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13. ABSTRACT (Maximum 200 words)  This project emphasized the production of smart material systems using advanced 3-dimensional processing techniques. The specific aim was the fabrication and characterization of smart organic/inorganic composites at the mesoscale (~1nm - 1 mm length scale) to achieve improved performance. Two approaches were used: (i) the synthesis and processing of organic/inorganic composites and (ii) developing two novel materials systems. Synthesis and processing studies involve the use of three methods: (i) laser stereolithography, (ii) self-assembled monolayers, and (iii) 3-dimensional co-assembly. The two novel systems developed for use in sensor and actuator technologies were piezoelectric shell transducers and 1-3 piezocomposite hydrophones.  This is the final technical report for the project, covering period 06/19/1995 - 05/31/2001. Proof of concept and feasibility studies have successfully demonstrated (i) the utility of rapid prototyping in the fabrication of ceramic structures for use in sensor and actuator applications; (ii) the formation of mesostructured ceramics via templation of liquid crystal structures in solution; (iii) guided growth and orientation in microcontact printing microinfiltration; and (iv) optimization of piezo-composite properties through analytical modeling.					
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Sincerely,

Ilhan A. Aksay  
Professor, Chemical Engineering  
Princeton University

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**Smart Materials Systems through Mesoscale Patterning**

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**Scientific Progress and Accomplishments**

The accomplishments for the project are detailed in the following sections. Active projects during the period of performance include the following task areas:

1. Piezoelectric Cantilevers as Sensors  
*Wan Y. Shih, James S. Vartuli, David L. Milius, Huiming Gu, Xiaoping Li, Wei-Heng Shih, and Ilhan A. Aksay*
2. Dynamics of Piezoelectric Cantilevers-Size Sensors  
*Peter C. Y. Lee, Rui Huang, Ninghui Liu, and Arthur Ballato*
3. Synthesis and Characterization of PMN-PT Piezoelectrics  
*Huiming Gu, Wan Y. Shih, and Wei-Heng Shih*
4. Stereolithography of Organic/Inorganic Composites  
*Robert K. Prud'homme, Ilhan A. Aksay, David L. Milius, James S. Vartuli, Rajeev Garg, Aaron J. Dulgar, Peter J. Photos, Jim H. Lee, and James Liang*
5. Mesoscopic Composites as Small Materials Systems  
*George M. Whitesides, et al.*
6. Micropatterning through Field-Assisted Flow  
*Ilhan A. Aksay, George M. Whitesides, Sol M. Gruner, Robert K. Prud'homme, Dudley A. Saville, James S. Vartuli, Daniel M. Dabbs, Matt Trau, Srinivas Manne, Linbo Zhou, Anthony Ku, Hak Fei Poon, and Macit Ozenbas*
7. The Sponge Phase: Synthesis and Characterization  
*Sol M. Gruner, Karen J. Edler, Daniel M. Dabbs, Nan Yao, Aaron Rabinovitch, Akin Akinc, Robert K. Prud'homme, and Ilhan A. Aksay*
8. L<sub>3</sub> "Sponge" Phase: Applications  
*Daniel M. Dabbs, Sol M. Gruner, Karen J. Edler, Nan Yao, Aaron Rabinovitch, Akin Akinc, Robert K. Prud'homme, and Ilhan A. Aksay*

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**Patent Activity**

***Patents Awarded***

85. M. Trau, I.A. Aksay, D.A. Saville, "Method and Apparatus for Electrohydrodynamically Assembling Colloidal Structures," U.S. Patent # 5,855,753, January 05, 1999.
86. I. A. Aksay et al., "Biomimetic Pathways for Assembling Inorganic Thin Films and Oriented Mesoscopic Silicate Patterns through Guided Growth," U.S. Patent Application Serial No. 08/964 876; Docket No. 97-1376-1 (allowed). Licensed to American Biomimetic Corp.

***Patent Applications***

87. K. M. McGrath, D. M. Dabbs, I. A. Aksay, S. M. Gruner, "Formation of a Silicate Sponge (L3) Phase," U.S. Provisional Patent Application Serial No. 60/047,463; Docket No. 97-1407-1.
88. W. Happer, G. Cates, M.-F. Hsu, and I. A. Aksay, "Sol-Gel Coated Polarization Vessels," U.S. Provisional Patent Application Serial No. PCT/US98/16834; Docket No 98-1443-1.
89. R. K. Prud'homme, I. A. Aksay, and R. Garg, "Method for the Preparation of Ceramic Articles," U.S. Patent Application Serial No. 846,764; Docket No. 98-1470-1. (Co-owned by Dow Chemical Co.).
90. I.A. Aksay, R. Garg, R.K. Prud'homme, "Controlled Microarchitecture Ceramic by Stereolithography," U.S. Patent Application Serial No. 09/191,606, Docket No. 98-1500-1.

***Invention Disclosures***

91. J. S. Vartuli, , R. K. Prud'homme, W.-H. Shih, D. L. Milius, W. Y. Shih, X. Li and I. A. Aksay, "Multi-Layer Piezoelectric Laminate," Docket No. 98-1512-1.

<p align="center"><b>REPORT DOCUMENTATION PAGE (SF298)</b>  <b>(Continuation Sheet)</b></p>
---

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***Collaborating Faculty***

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**REPORT DOCUMENTATION PAGE (SF298)**  
**(Continuation Sheet)**

**Technology Transfer**

***Collaborations and Interactions***

Army Research Office

ARO, U.S. Army Research Laboratory, Arthur Ballato, Fort Monmouth, New Jersey

Industrial

PrinDrex technology licensed to Leading Edge Ceramics

Sponge phase technology licensed to American Biomimetics

Ceramic stereolithography licensed to Johnson and Johnson

L<sub>3</sub> phase technology transfer agreement with Lucent Technologies

***Other Industrial Connections***

<b>Company/Corporation</b>	<b>Contact</b>	<b>Company/Corporation</b>	<b>Contact</b>
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EDO Corporation Salt Lake City, Utah	Mr. Donald Bascow	TPL, Inc. Albuquerque, New Mexico	Mr. Hap Stoller
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# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

**ILHAN A. AKSAY<sup>§</sup>, SOL M. GRUNER<sup>†</sup> PETER C. Y. LEE<sup>‡</sup>,  
ROBERT K. PRUD'HOMME<sup>§</sup>, WEI-H. SHIH<sup>\*</sup>, WAN Y. SHIH<sup>\*‡</sup>  
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OPERATIONS RESEARCH, AND PRINCETON MATERIALS INSTITUTE  
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**<sup>#</sup>DEPARTMENT OF CHEMISTRY, HARVARD UNIVERSITY  
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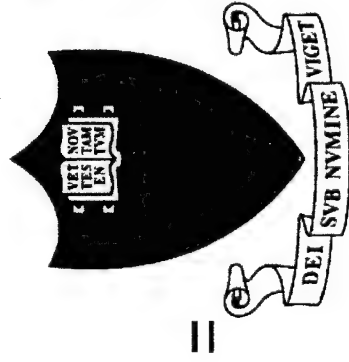
**<sup>†</sup>DEPARTMENT OF PHYSICS, CORNELL UNIVERSITY  
ITHACA, NEW YORK 14853**

**<sup>\*</sup>MATERIALS ENGINEERING DEPARTMENT, DREXEL UNIVERSITY  
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## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**



Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

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# Smart Materials Systems through Mesoscale Patterning

Ilhan A. Aksay,<sup>§</sup> Sol M. Gruner,<sup>†</sup> Peter C. Y. Lee,<sup>‡</sup>

Robert K. Prud'homme,<sup>§</sup> Wei-H. Shih,<sup>\*</sup>

Salvatore Torquato,<sup>‡</sup> and George M. Whitesides<sup>#</sup>

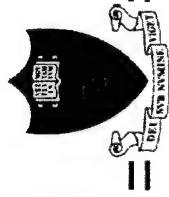
Departments of <sup>§</sup>Chemical Engineering, <sup>‡</sup>Civil Engineering and Operations Research,  
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Princeton University

<sup>†</sup>Department of Physics, Cornell University

<sup>\*</sup>Materials Engineering Department, Drexel University

<sup>#</sup>Department of Chemistry, Harvard University

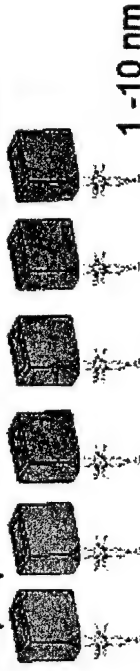
---



# Goals and Organization

## Self Assembly

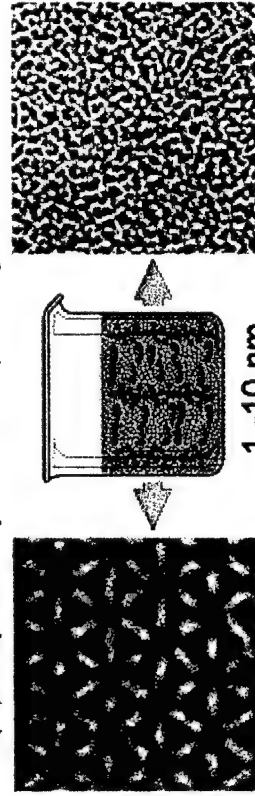
### (a) Amphiphilic and Protein Membranes



1 - 10 nm

Groves, Hecht, Aksay (NSF)

### (b) Liquid Crystal Templating



1 - 10 nm

Cubic phase

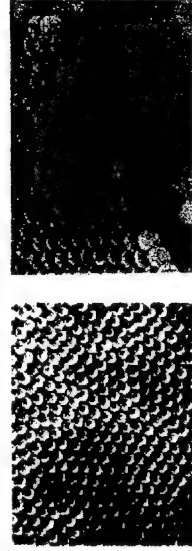
Dabbs, Saville, Aksay

### (c) Block Copolymer Templating (NSF)



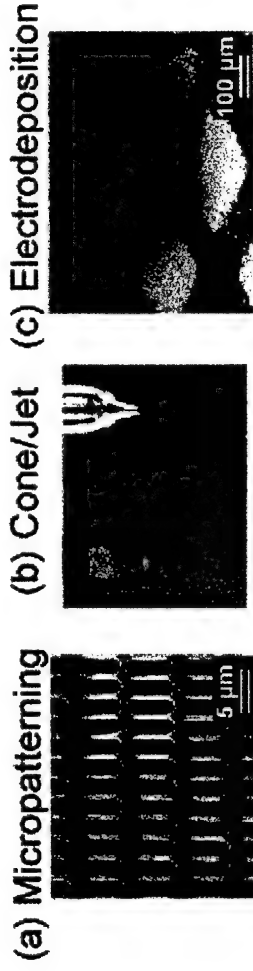
10 - 100 nm

### (d) 2D and 3D Colloidal Structures

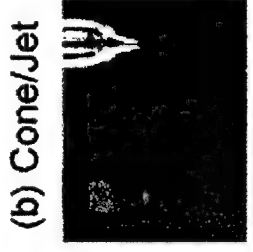
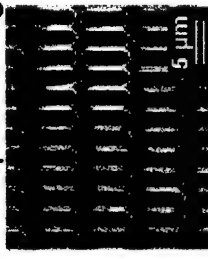


Saville, Aksay

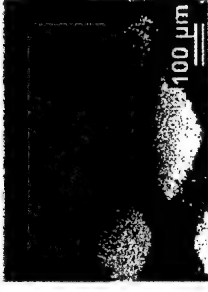
## Laminating and Micropatterning by Field-Assisted Flow



(a) Micropatterning



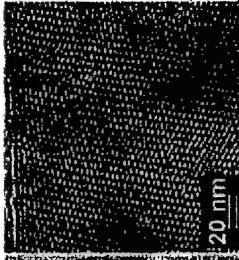
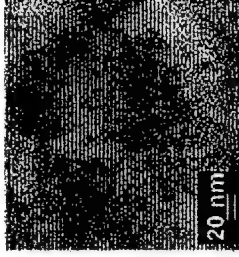
(b) Cone/Jet (c) Electrodeposition

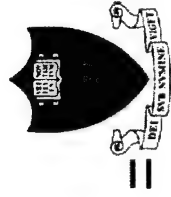


## PROCESSING TECHNIQUES

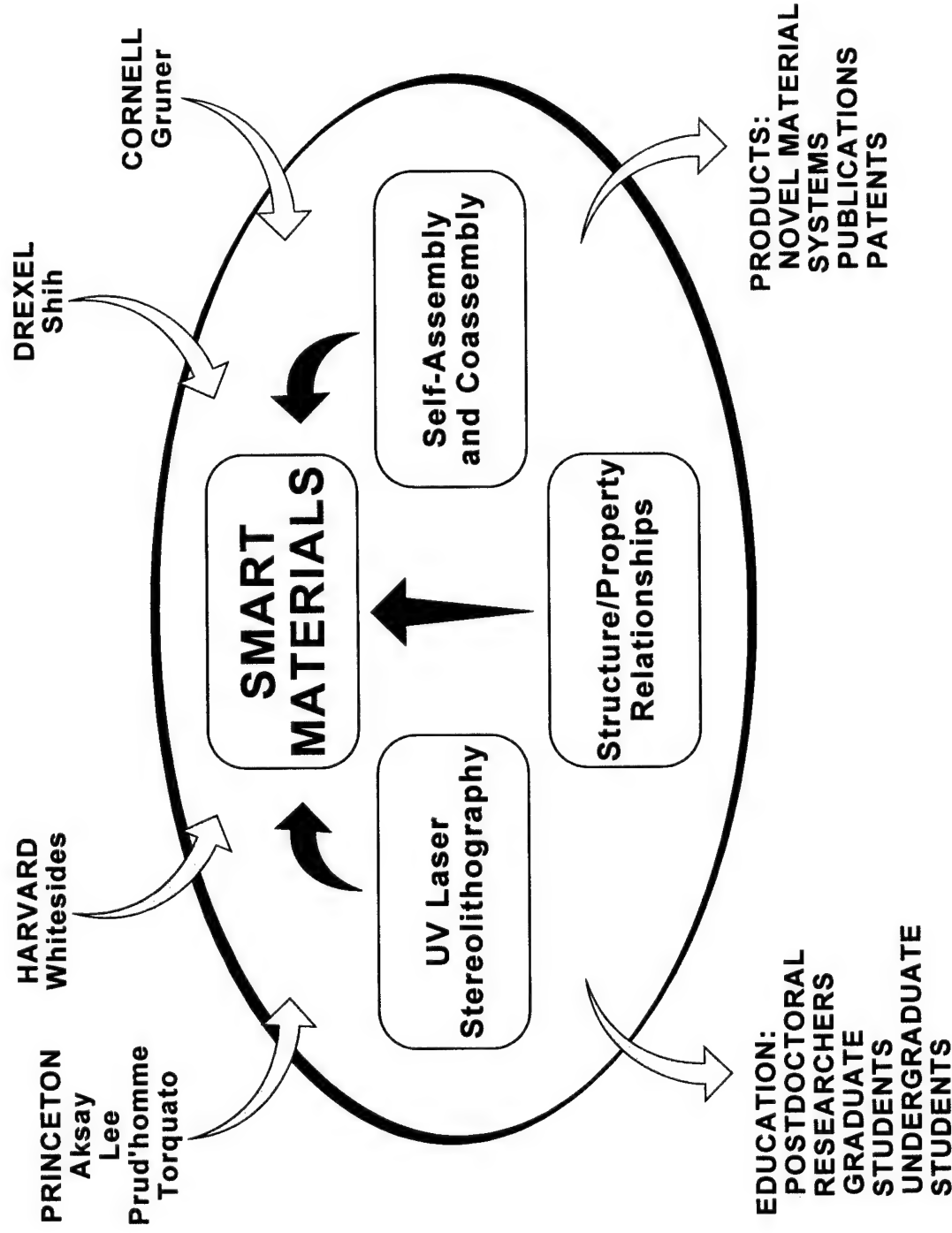
## OPTIMAL PROPERTIES

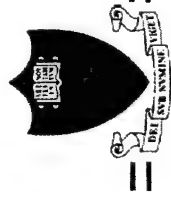
Hierarchically Structured  
Nano- and Microlaminates  
Suo, Evans, Soboyejo, Saville,  
Groves, Aksay (NSF)



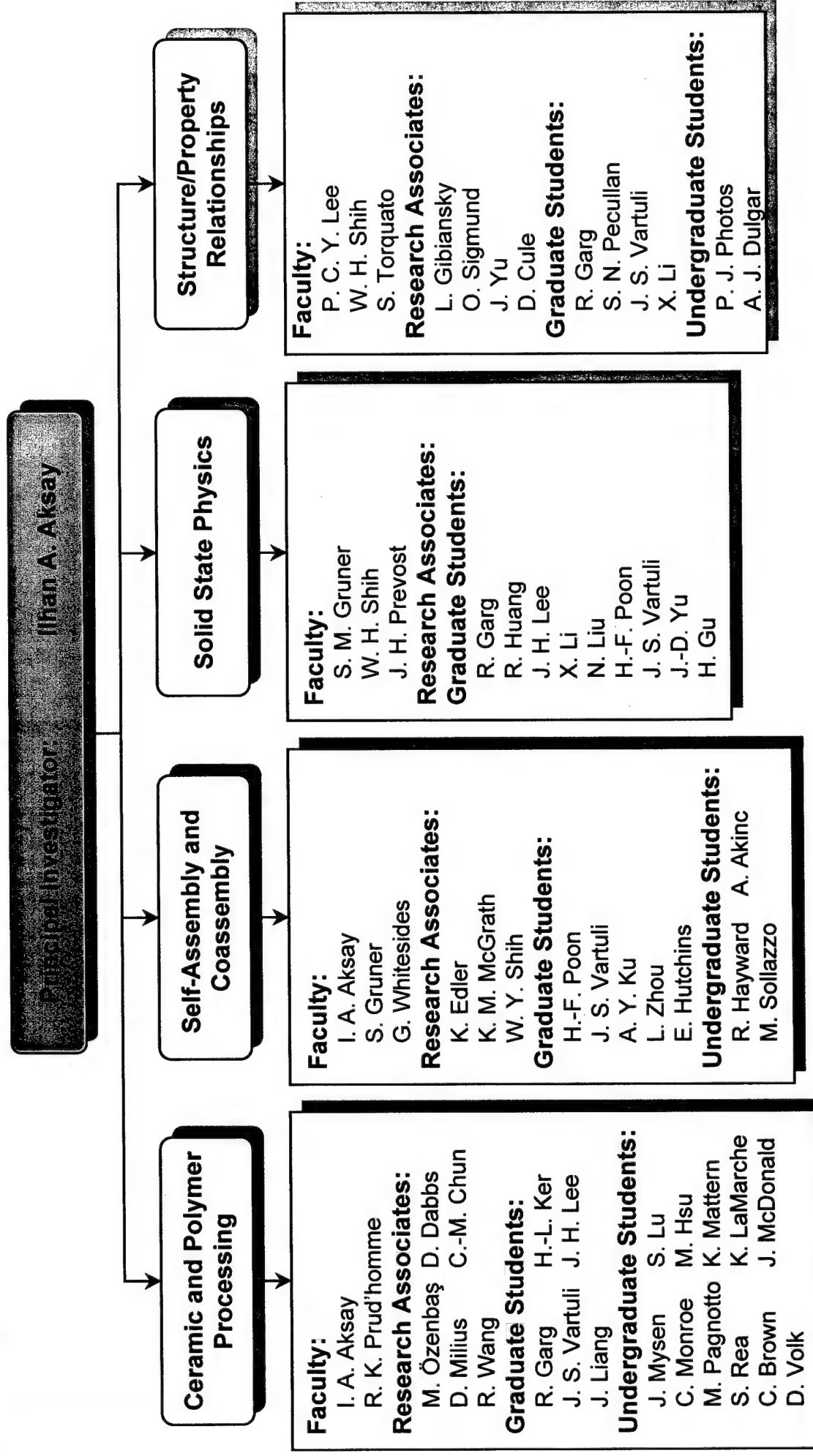


# Research Dynamics: We Kept Our Promise!





# Organization of Research Teams



# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***Piezoelectric Cantilevers as Sensors***

**WAN Y. SHIH<sup>§,#</sup>, JAMES S. VARTULI<sup>§,#</sup>, DAVID L. MILIUS<sup>§,#</sup>,  
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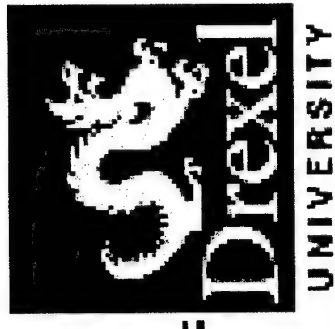
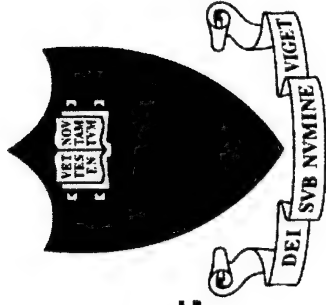
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## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**



# Piezoelectric Cantilevers as Sensors

Wan Y. Shih,<sup>\*,†</sup> Xiaoping Li,<sup>\*</sup> Huiming Gu,<sup>\*</sup>

Wei-Heng Shih,<sup>\*</sup> I. A. Aksay<sup>†</sup>

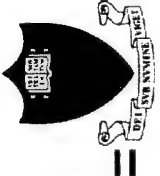
<sup>\*</sup>Department of Materials Engineering, Drexel University

<sup>†</sup>Department of Chemical Engineering and Princeton Materials Institute,  
Princeton University

---

*Supported by the ARO/MURI under Grant No. DAAH04-95-1-0102*





- *Using cantilevers as microsensors in a wet environment, e.g., in a biological system*
  - *Detection of human viral pathogens, cholesterol, protein, etc. in blood supply and in blood stream*
    - ⇒ In a liquid environment, damping is important
    - ⇒ How does the effect of damping changes as the dimension of the device shrinks?
-

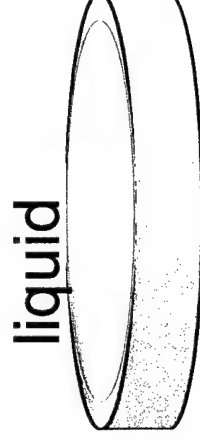
## Existing viscosity sensors

- *Using resonance-frequency change and/or peak broadening to deduce the liquid viscosity.*

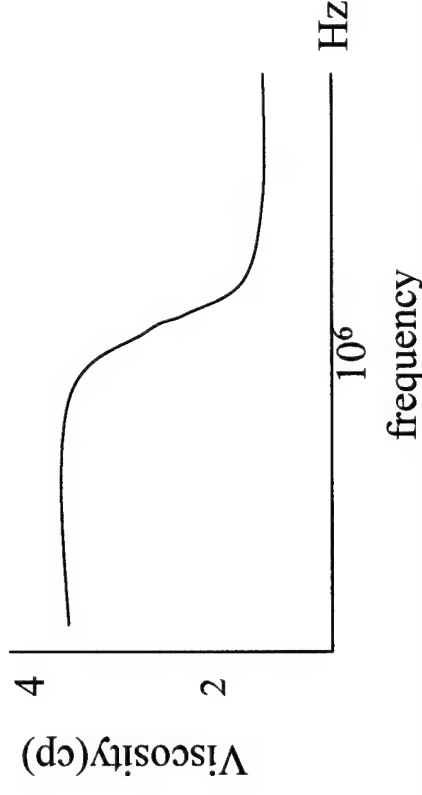
(1) Thickness-mode sensors  
(1-50 MHz)

Quartz membrane

Ultrasonic viscosity sensors



**Disadvantages: higher frequency viscosity depends on frequency**



## (2) Flexural sensors:

### (I) PZT-bimorph-disk oil viscosity sensors

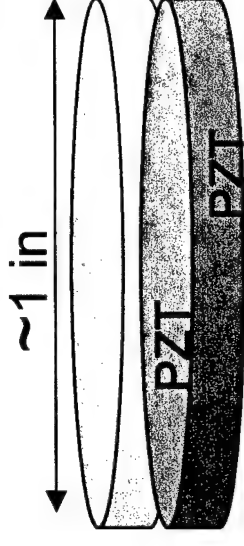
Advantage:

lower frequencies (kHz)

Disadvantage:

low sensitivity

frequency change ~ 2-3%



### (II) silicon, silicon nitride microcantilever viscosity sensors

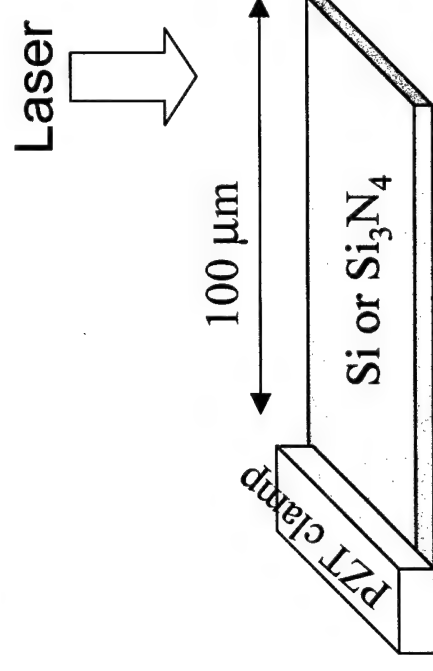
Advantages:

(i) lower frequencies (kHz)

(ii) higher sensitivity

frequency change ~ 100%  
for viscosity change 1-200 cp

Disadvantage: (i) require a laser



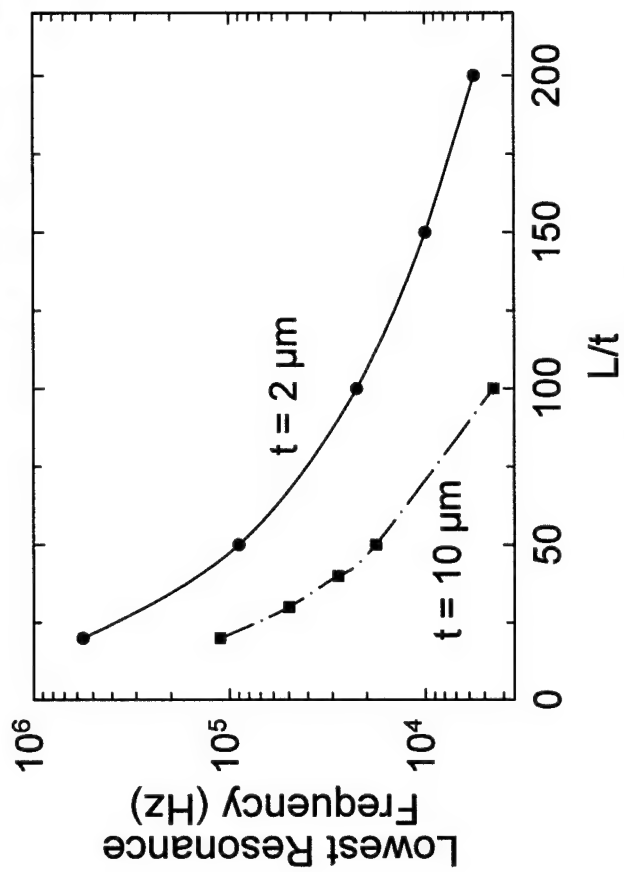
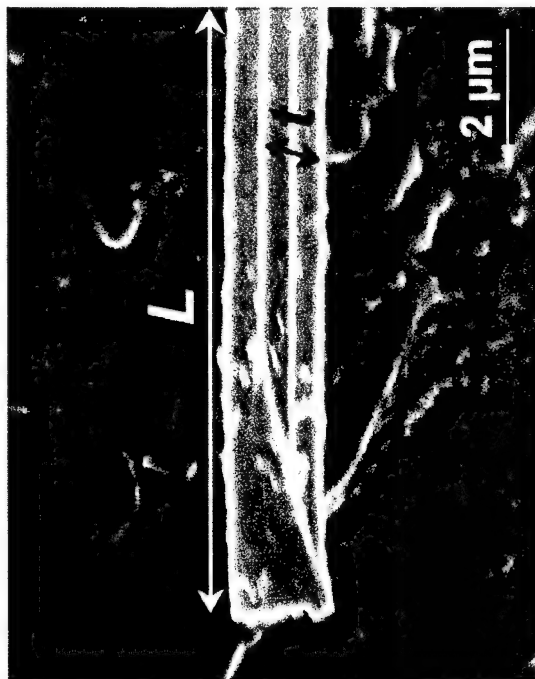
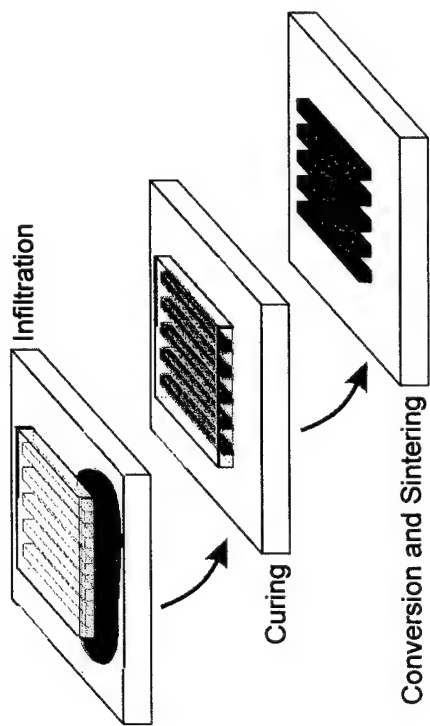


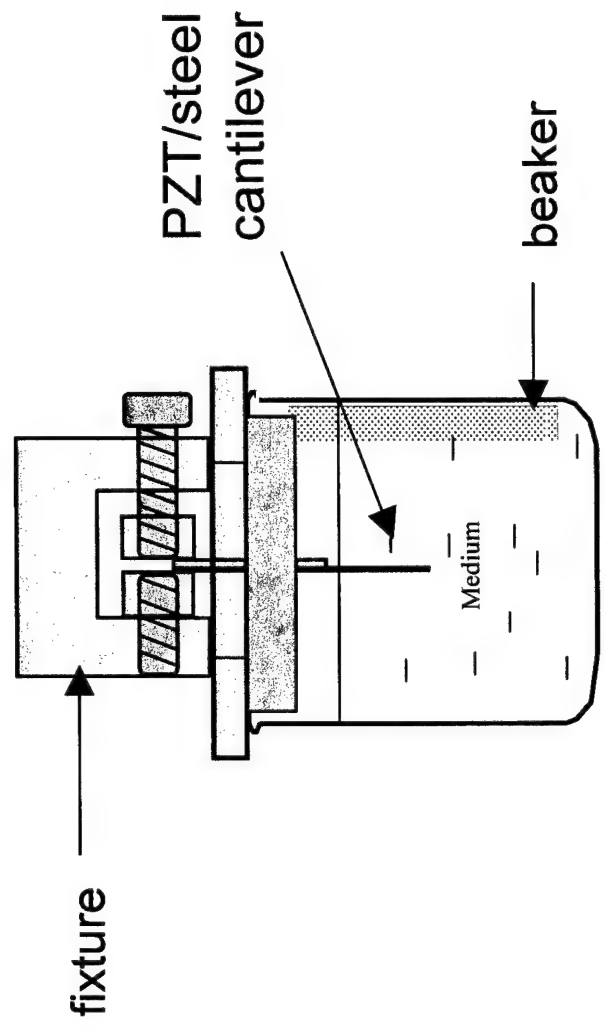
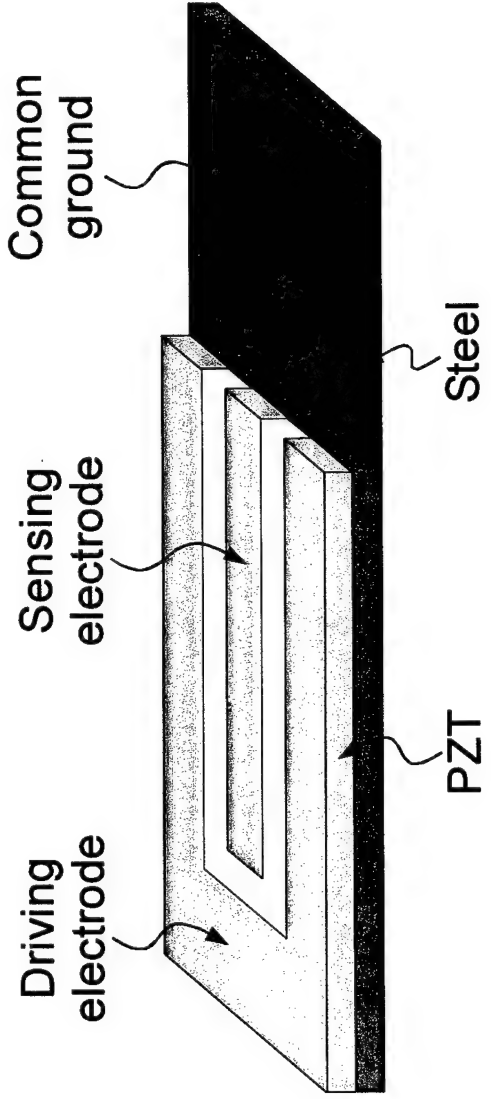
# Objectives

***(1) To develop a viscosity sensor that***

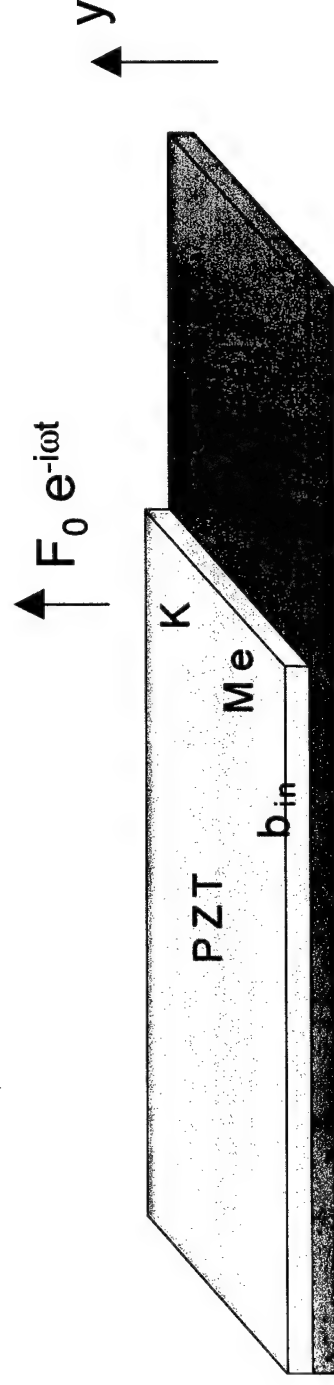
- operates at a low frequency
- easy and cheap to operate
- desirable sensitivity

***(2) To explore other sensing possibilities (e.g.,  
material sensing) in a wet environment***





$$(Me + MI) \frac{d^2 y}{dt^2} + (b_{in} + b) \frac{dy}{dt} + Ky = F_0 e^{-i\omega t}$$



$\omega$  =angular frequency,

$Me$  =effective mass at the tip of the cantilever

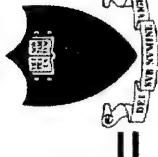
$K$  =effective spring constant at the tip of the cantilever

$MI$  =induced mass from the liquid

$b$  =damping coefficient due to the viscous liquid,

$b_{in}$  =the intrinsic damping coefficient of the cantilever.





$$y = y_0 e^{-i\omega t}$$

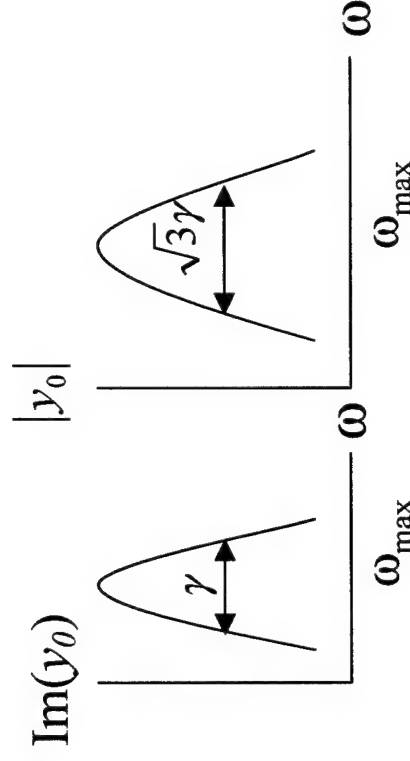
$$y_0 = \frac{-F_0}{(\omega^2 - \omega_0^2) + i\omega\gamma}$$

$$y_{0,\max} \text{ and } \text{Im}(y_0) \text{ occurs at } \omega_{\max}: \quad \omega_{\max}^2 = \omega_0^2 - \frac{1}{2}\gamma^2$$

$$\text{at } \omega = \omega_{\max}$$

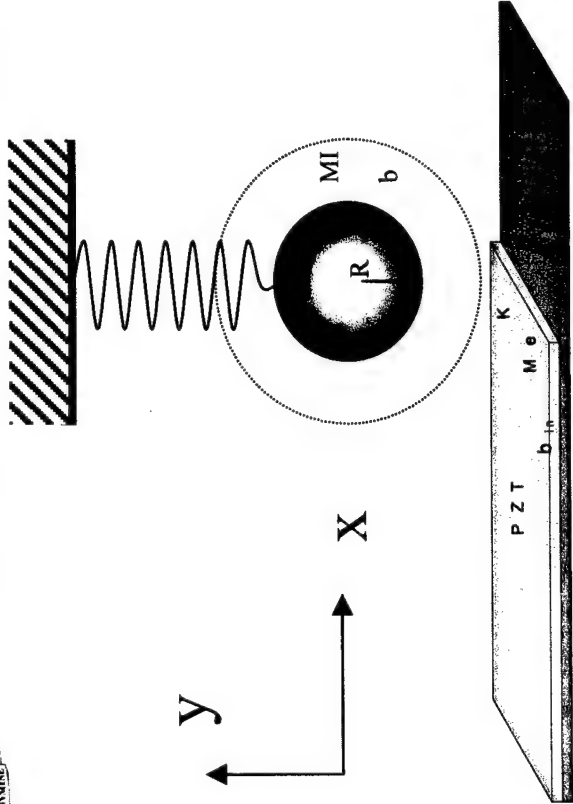
$$|y_0|_{\max} = \frac{F_0}{\omega_{\max}\gamma}$$

$$\text{Im}(y_0)_{\max} = \frac{F_0}{\omega_{\max}\gamma}$$



$$\omega_0 = \sqrt{\frac{K}{Me + Ml}} = \text{resonance frequency in liquid without damping}$$

$$\gamma = \frac{b + b_{in}}{Me + Ml} = \text{damping coefficient per unit mass}$$



$R$  = radius of oscillating sphere

$\rho$  = liquid density

$\eta$  = liquid viscosity

The induced mass

$$MI = \frac{2\pi R^3}{3} \rho \left( 1 + \frac{9\delta}{4R} \right)$$

The damping factor

$$b = \frac{6\pi\eta R^2}{\delta} \left( 1 + \frac{\delta}{R} \right)$$

$$\delta = \sqrt{\frac{2\eta}{\rho\omega}} = \text{the decay length in the liquid}$$

For  $\omega=0$ :

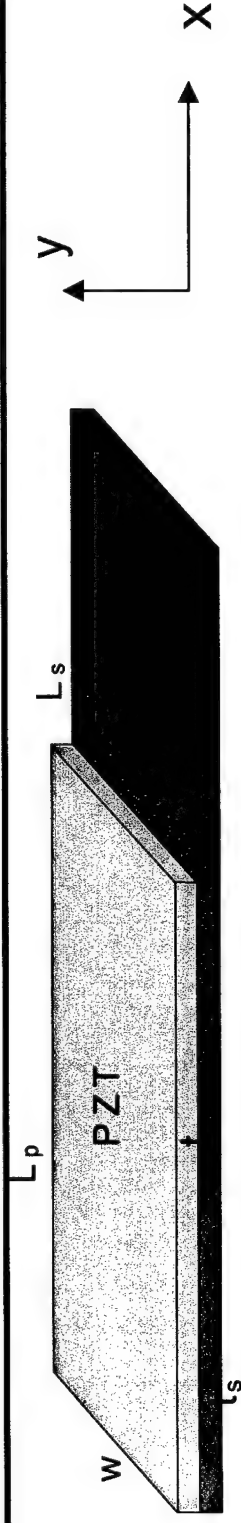
$$MI_0 = \frac{3\pi R^2}{2} \delta \rho$$

$$b_0 = 6\pi\eta R$$

For  $\omega=\infty$ :

$$MI_\infty = \frac{2\pi R^3}{3} \rho$$

$$b_\infty = \frac{6\pi\eta R^2}{\delta}$$



The spring constant at the end of the PZT plate (at  $x = L_p$ ):

$$K = \frac{3D_p w}{L_p^3}$$

For the present cantilever, the effective mass

$$Me = 0.236(\rho_p h_p + \rho_s h_s)wL_p + \rho_s h_s wL_s$$

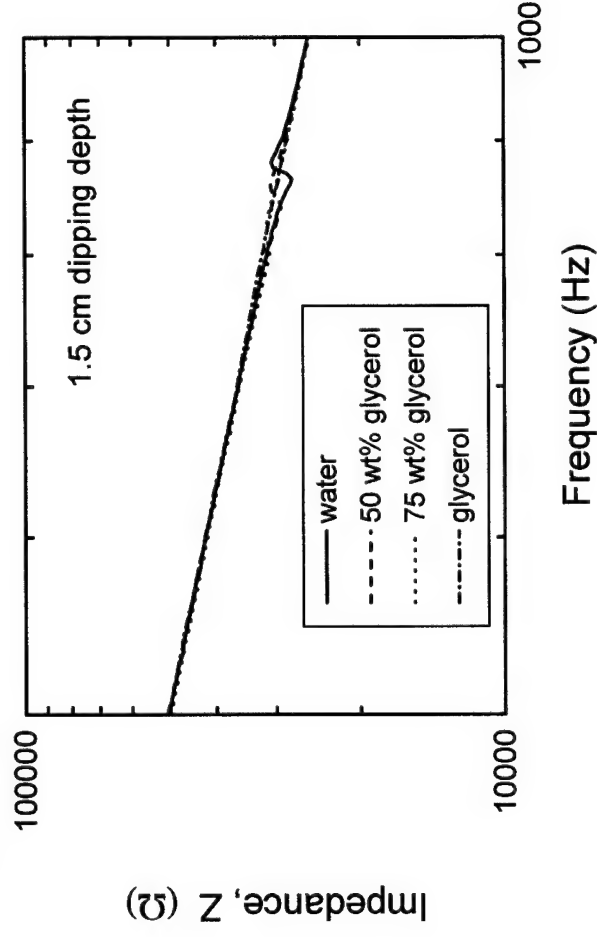
$D_p$  = bending modulus of the PZT/steel

$$D_p = w \frac{E_p^2 h_p^4 + E_s^2 h_s^4 + 2E_p E_s h_p h_s (2h_p^2 + 2h_s^2 + 3h_p h_s)}{12(E_p h_p + E_s h_s)}$$

The lowest resonance frequency in air:  $f_1 = \frac{1}{2\pi} \sqrt{\frac{K}{Me}}$

$\rho_p, \rho_s$  = densities of PZT and steel

$E_p, E_s$  = Young's moduli of PZT and steel



Impedance

$$Z = \frac{-i}{\omega c} + iZ_i$$

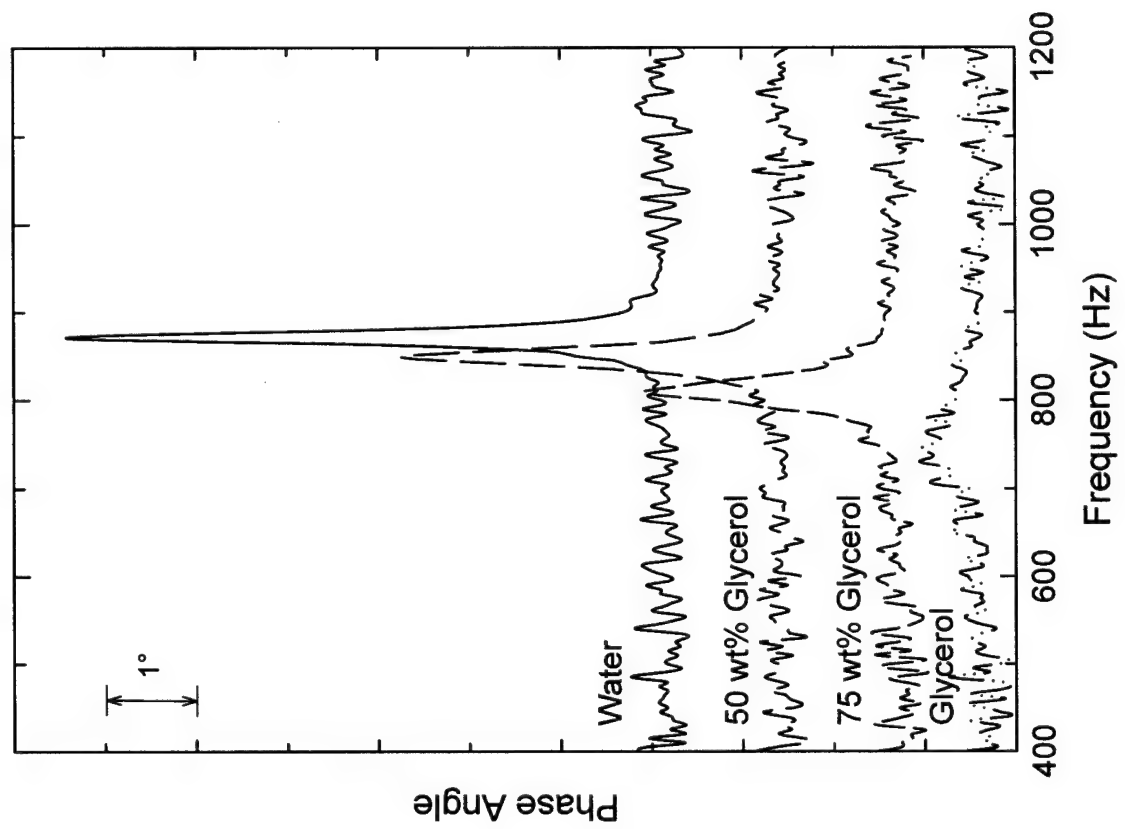
$$c = 6.0 \text{ nF}$$

$$iZ_i = \frac{i\alpha}{(\omega^2 - \omega_0^2) + i\omega\gamma}$$

$c$  = capacitance of unimorph

$iZ_i$  = induced impedance due to flexural displacement

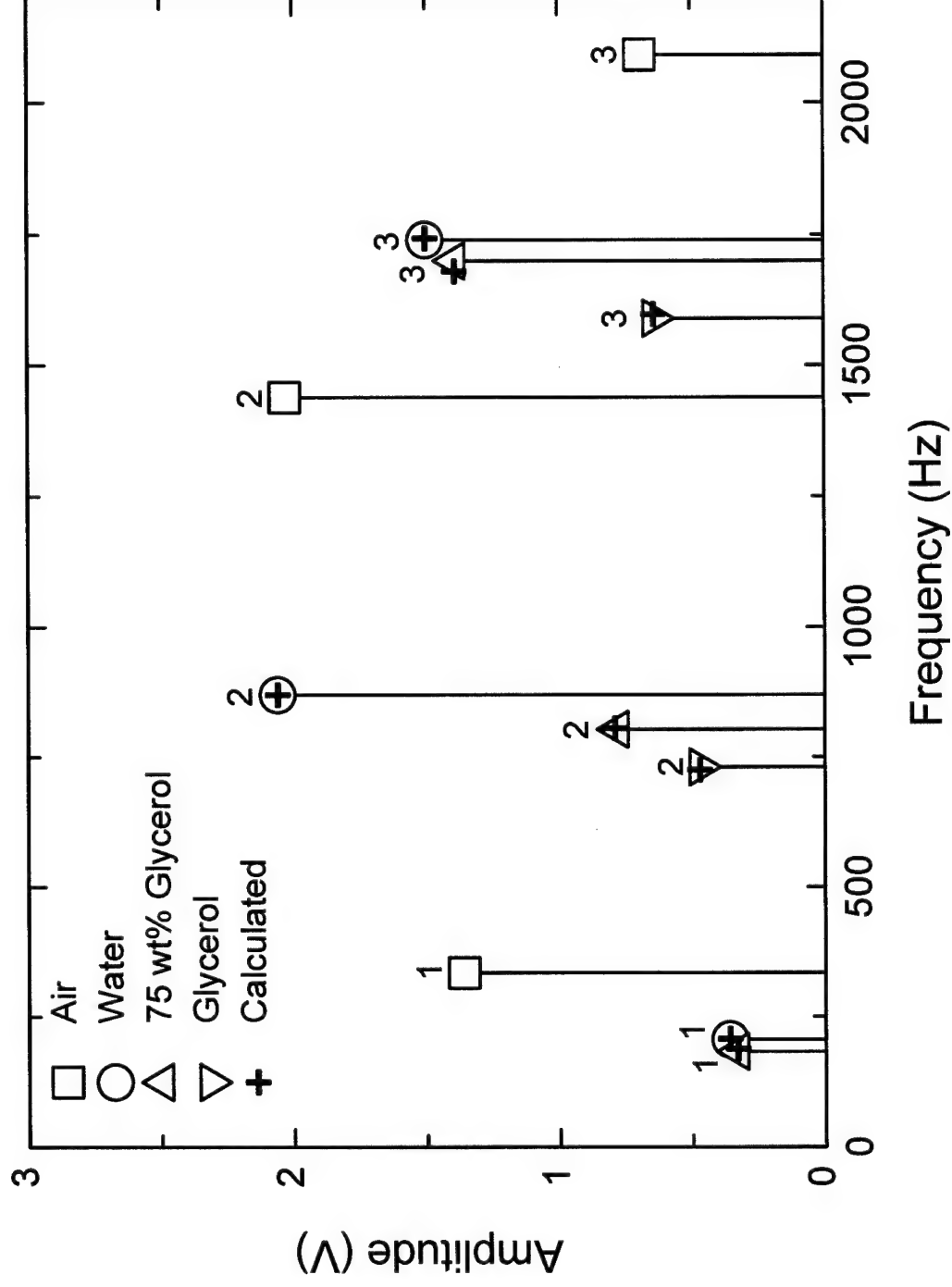
$\alpha$  = proportional constant

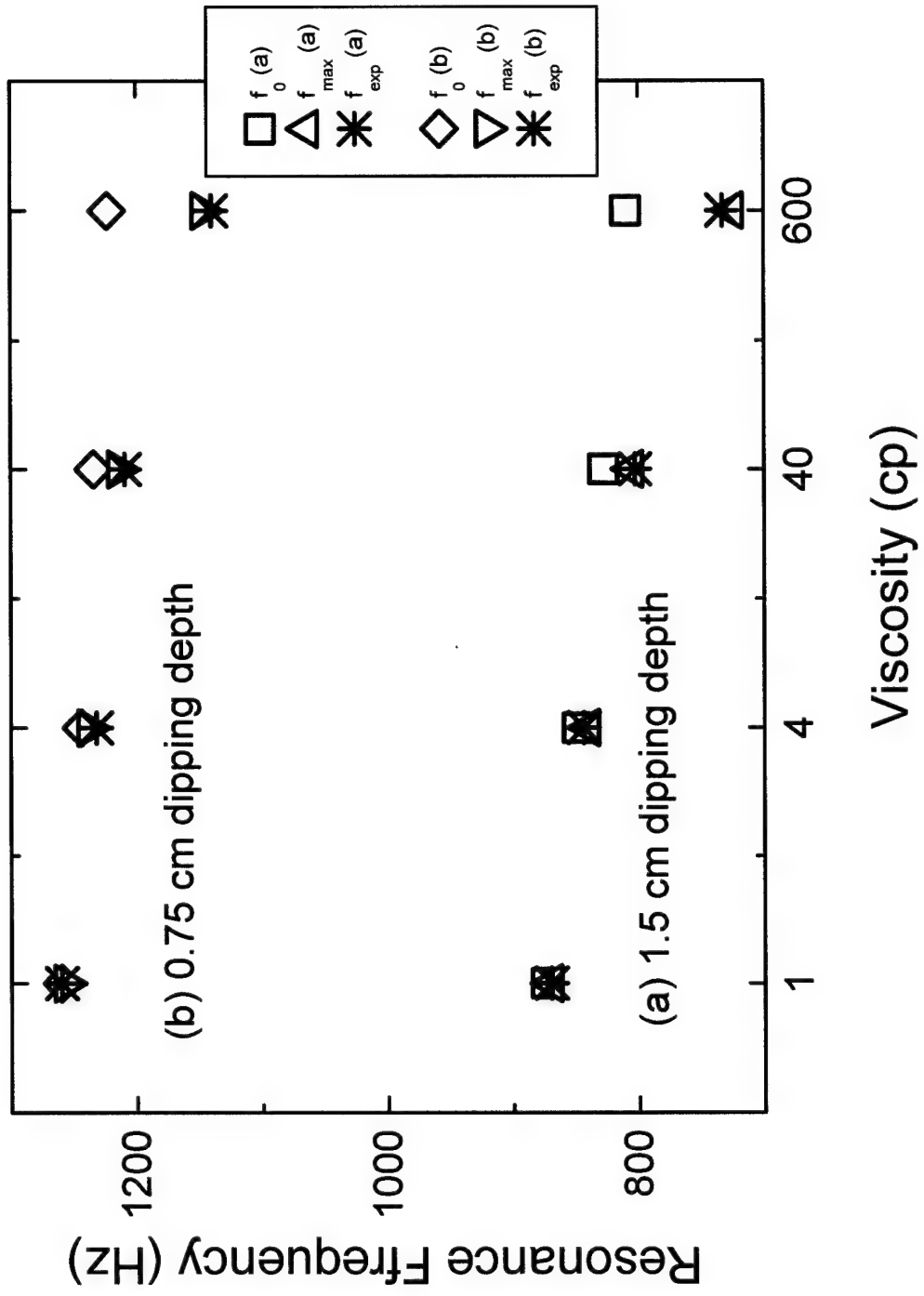


$$b_{in}/2\pi \approx 9.0 \times 10^{-3} \text{ Hz/kg}$$

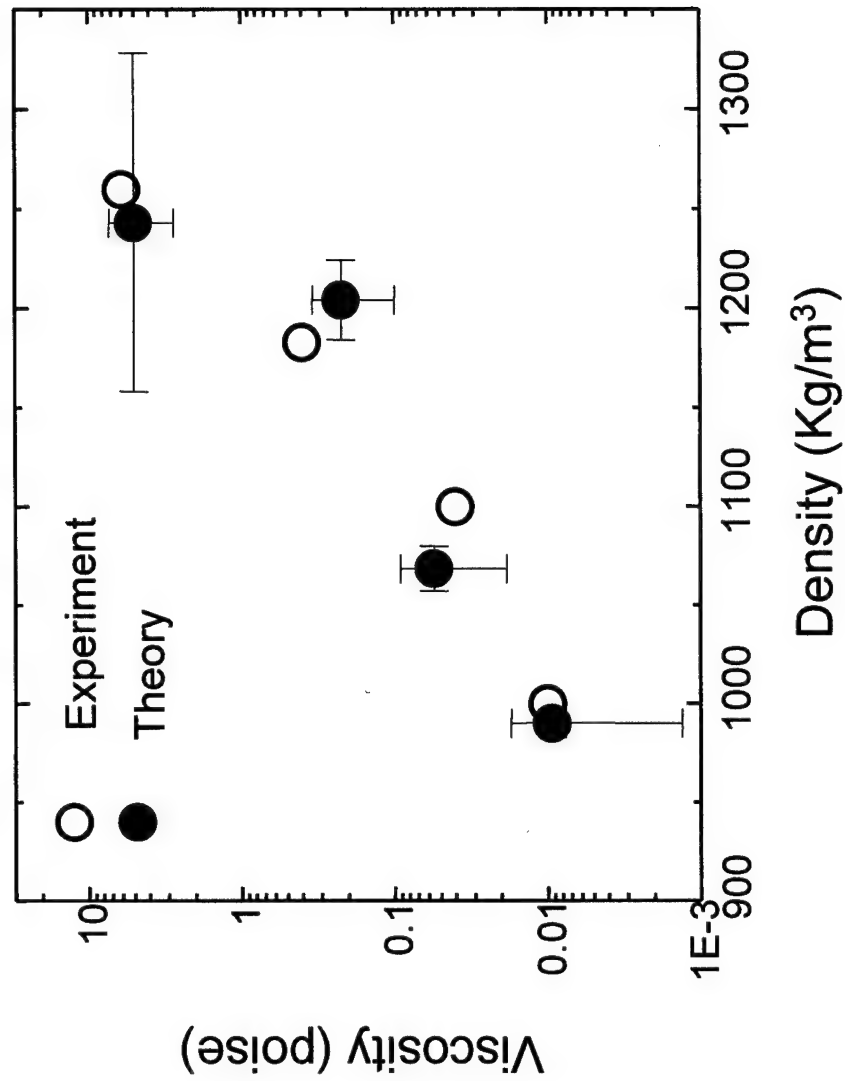
# Induced Voltage at Resonance

Input=10V









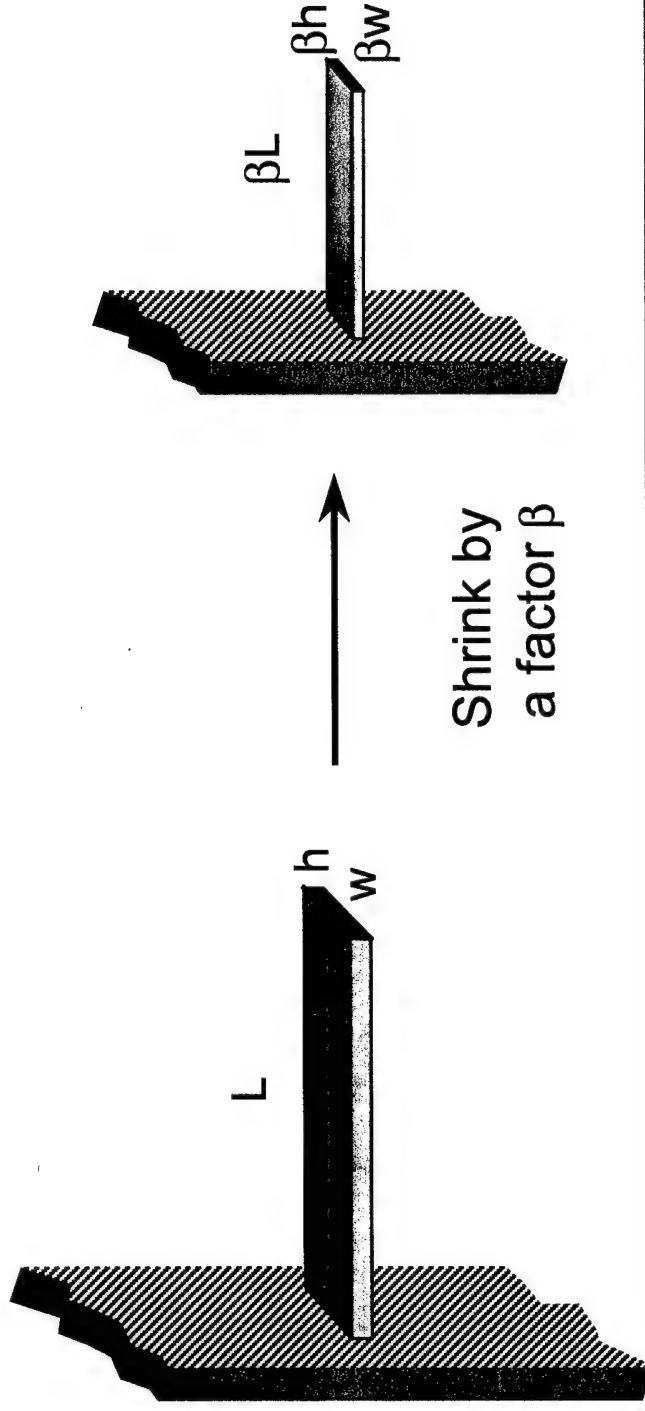
# Size effect: Scaling Analysis

With 1.5 cm dipping depth

$MI = 1.0 \times 10^{-3}$  in water  
 $= 1.97 \times 10^{-3}$  kg, in 75 wt % glycerol

$Me = 3.09 \times 10^{-4}$  kg

Only  $MI$  is considered



$$K(\beta) \propto \beta K.$$

(1) *High-frequency low-viscosity*

(2) *Low-frequency, high-viscosity*

$$M\Gamma_0(\beta) \propto \beta^2 f_i^{-1/2}$$

$$M\Gamma_\infty(\beta) \propto \beta^3 M\Gamma_\infty$$

$$f_i(\beta) \approx \sqrt{\frac{K(\beta)}{M\Gamma_\infty(\beta)}} \propto \beta^{-1} f_i$$

$$f_i(\beta) \propto \sqrt{\frac{K(\beta)}{M\Gamma_0(\beta)}} \propto \beta^{-1/2} (f_i(\beta))^{1/4}$$

$$\Rightarrow f_i(\beta) \propto \sqrt{\frac{K(\beta)}{M\Gamma_0(\beta)}} \propto \beta^{-2/3}$$

$$\Rightarrow M\Gamma_0(\beta) \propto \beta^{7/3}$$

The damping factor

$$b_\infty(\beta) \propto \beta^{3/2} b_\infty$$

$$\gamma_{liq}(\beta) = \beta^{-3/2} \gamma_{liq}$$

$$Q(\beta) = \frac{f_{\max}}{\gamma} \propto \beta^{1/2} Q$$

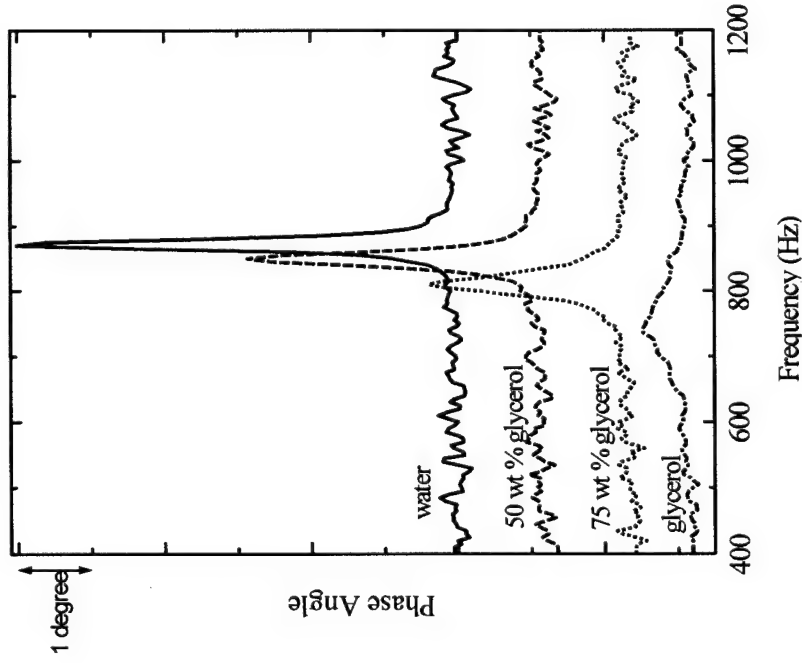
The damping factor

$$b_0(\beta) \propto \beta^1 b_0$$

$$\gamma_{liq}(\beta) = \frac{b_0(\beta)}{M\Gamma_0(\beta)} \propto \beta^{-4/3}$$

$$Q(\beta) = \frac{f_{\max}}{\gamma} \propto \beta^{2/3}$$

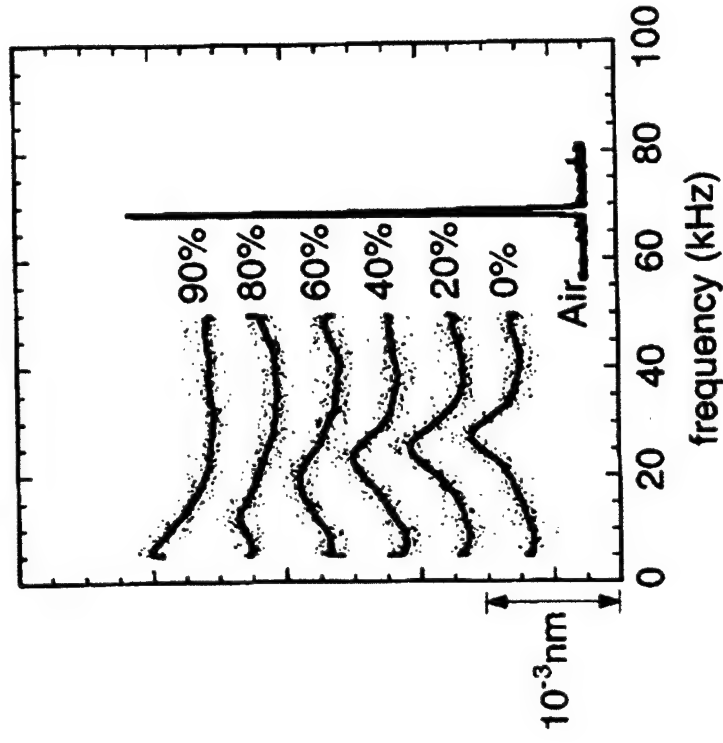
## Present cantilever



$L=3\text{cm}$

$$\begin{aligned} f_{\text{water}} &= 870 \text{ Hz} \\ f_{\text{glycerol}} &= 700 \text{ Hz} \\ \Delta f / f_{\text{water}} &= 30\% \end{aligned}$$

## Microcantilever



$L=100\mu\text{m}$

$$\begin{aligned} f_{\text{water}} &= 25 \text{ kHz} \\ f_{\text{glycerol}} &= 5 \text{ kHz} \\ \Delta f / f_{\text{water}} &= 80\% \end{aligned}$$

P. I. Oden et al., Appl. Phys. Lett. 68(26), 3814-3816 (1996).



## Conclusions

- (1) Piezoelectric cantilevers can effectively sense the change in the liquid viscosity and density.***
  - (2) The liquid viscosity and density can be accurately determined by the oscillating-sphere model.***
  - (3) Miniaturized cantilevers are more sensitive to liquid viscosity and density change (both in terms of resonance-frequency shift and peak broadening).***
-

# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***Dynamics of Piezoelectric Cantilevers- Size Effects***

**PETER C. Y. LEE\*, RUI HUANG\*, NINGHUI LIU\*,  
AND ARTHUR BALLATO<sup>‡</sup>**

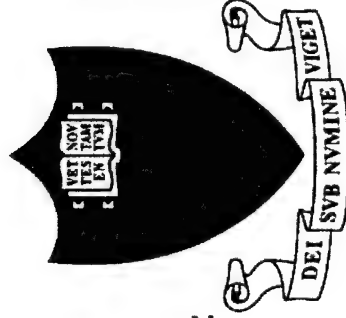
**\*DEPARTMENT OF CIVIL ENGINEERING AND OPERATIONS RESEARCH, AND  
PRINCETON MATERIALS INSTITUTE  
PRINCETON UNIVERSITY, PRINCETON, NEW JERSEY 08544**

**<sup>§</sup>DEPARTMENT OF MATERIALS ENGINEERING  
DREXEL UNIVERSITY, PHILADELPHIA, PENNSYLVANIA 19104**

## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**



Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

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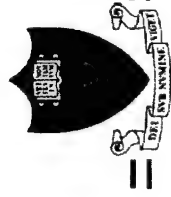
# Dynamics of Piezoelectric Cantilevers—Size Effects

P. C. Y. Lee,<sup>†</sup> R. Huang,<sup>†</sup> N. Liu,<sup>†</sup> and A. Ballato<sup>‡</sup>

<sup>†</sup>Department of Civil and Environmental Engineering  
Princeton Materials Institute  
Princeton University, Princeton, NJ 08544-5263

<sup>‡</sup>US Army Communication-Electronics Command  
AMSEL-RD-CS, Fort Monmouth, NJ 07703

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# Dynamics of Piezoelectric Shell Transducers

## ● *Objectives*

- Model and analyze piezoelectric plate and shell resonators with thickness-graded properties
- Examine and understand sensitivities of resonance frequencies to changes in properties or deposits on faces

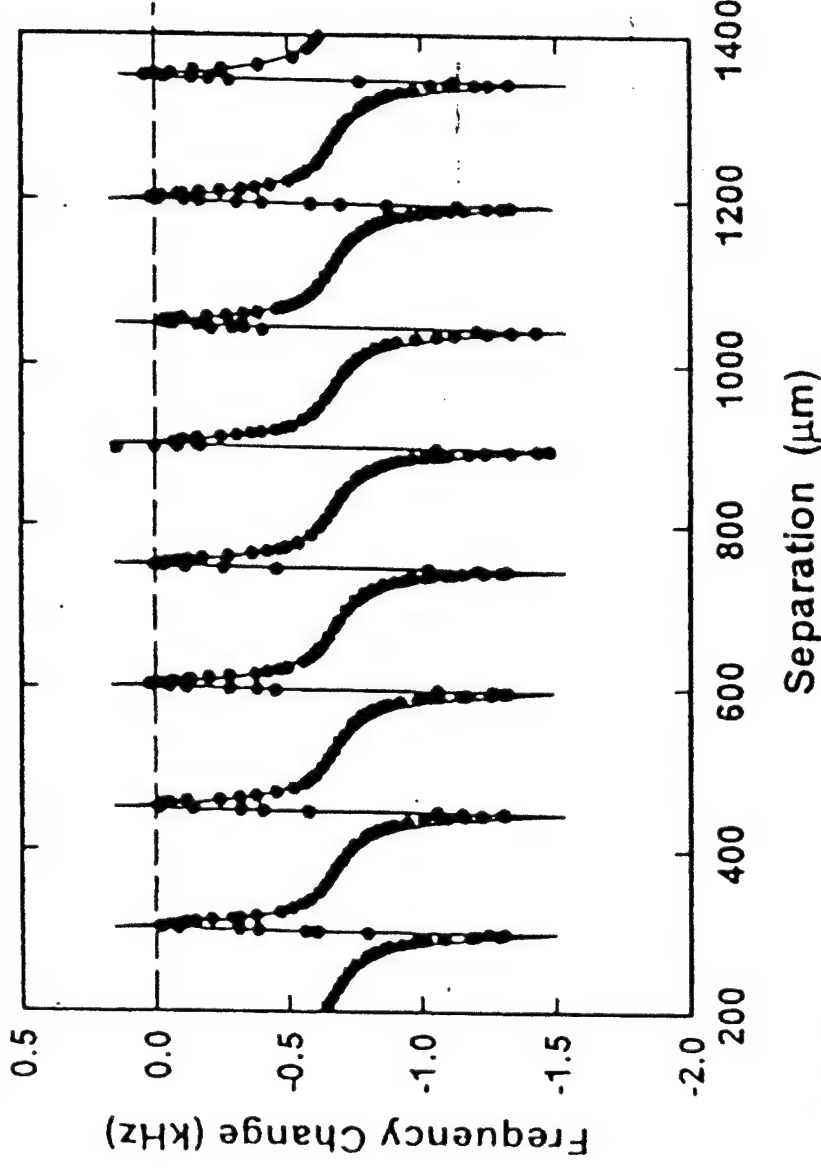
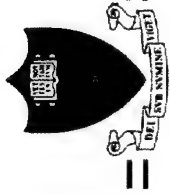
## ● *Approach*

- Deduce system of 2-D governing equations
- Study finite plate problems and compare with data
- Model and analyze resonators for sensors and actuators

## ● *New Achievements*

- Solution of thickness-shear vibrations for quartz sensors
  - 3-D theory of piezoelectricity with loss mechanisms
-





## ● *Future Studies*

- Continue study on the effects of liquid and solid layers on frequencies of resonators for sensing applications
- Study vibrations and attenuations of ceramic resonators by including dissipation (e.g., internal friction and DC conductivity)
- Study vibrational characteristics of micro-PZT beams for actuating and sensing applications

# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***Synthesis and Characterization of PMN-PT Piezoelectrics***

**HUIMING GU\*, WAN Y. SHIH<sup>§</sup>, WEI-HENG SHIH\*,**

**\*DEPARTMENT OF MATERIALS ENGINEERING  
DREXEL UNIVERSITY, PHILADELPHIA, PENNSYLVANIA 19104**

**<sup>§</sup>DEPARTMENT OF CHEMICAL ENGINEERING, AND  
PRINCETON MATERIALS INSTITUTE  
PRINCETON UNIVERSITY, PRINCETON, NEW JERSEY 08544**

## **FIFTH ARO/MURI PROGRAM REVIEW**

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# **Synthesis and Characterization of PMN-PT Piezoelectrics**

**Huiming Gu, Wan Y. Shih, and Wei-Heng Shih**

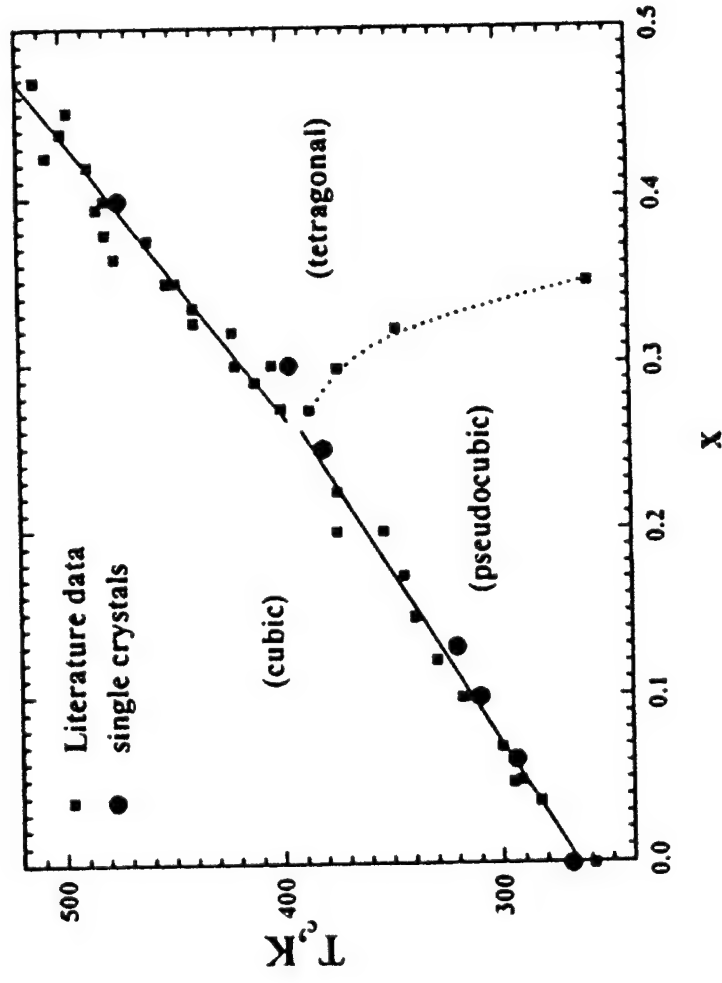
**Drexel University**

*Supported by ARO/MURI, DAAH04-95-1-0102*

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Prin-Drex actuators: PZT/PZT, PZT/ZnO  $\rightarrow$  High displacement due to domain switching at high electric fields

PMN-PT is potentially more effective than PZT



PMN-PT: multi-layer capacitors and electrostrictive applications

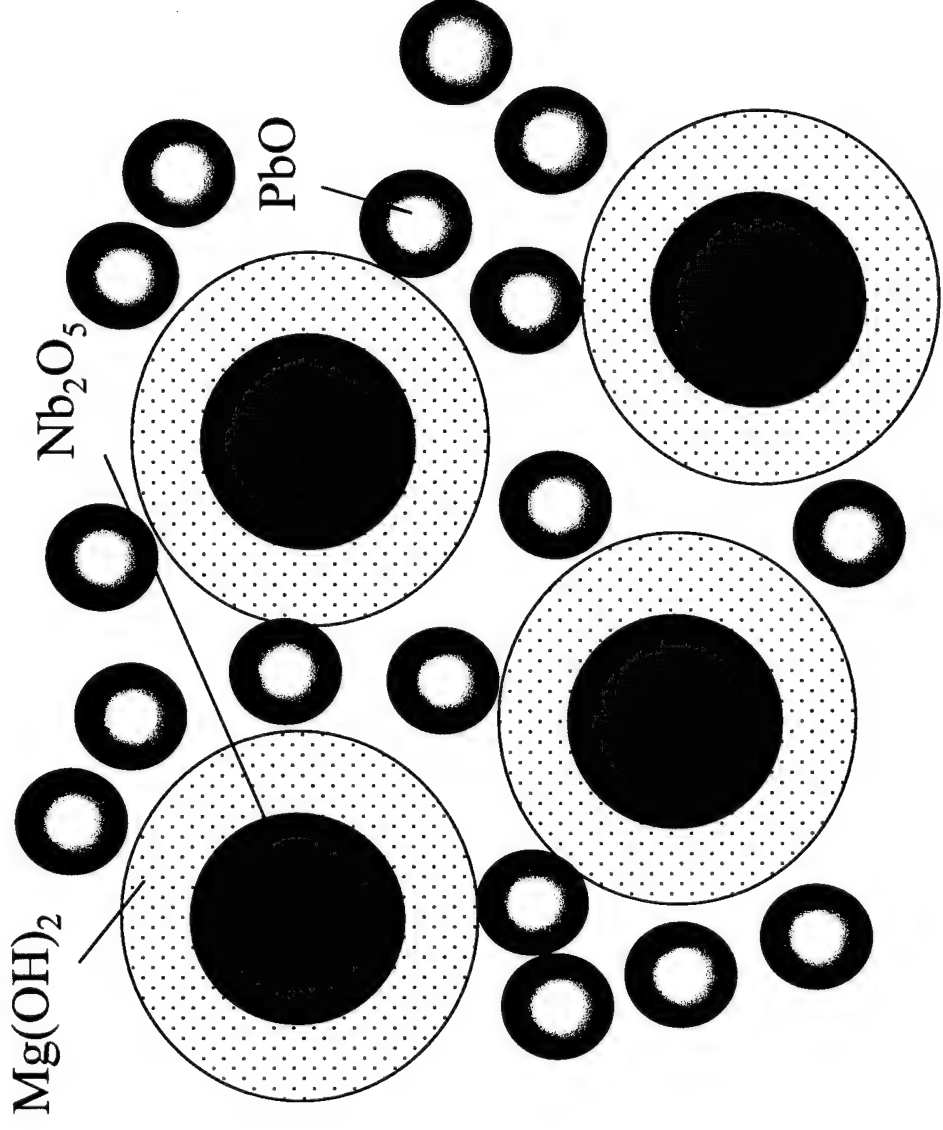
Difficult to obtain single-phase perovskite: presence of  
pyrochlore phase

Columbite method: Swartz and Shrout (1982)  
Prevention of reactions between  $Nb_2O_5$  and  $PbO$ .

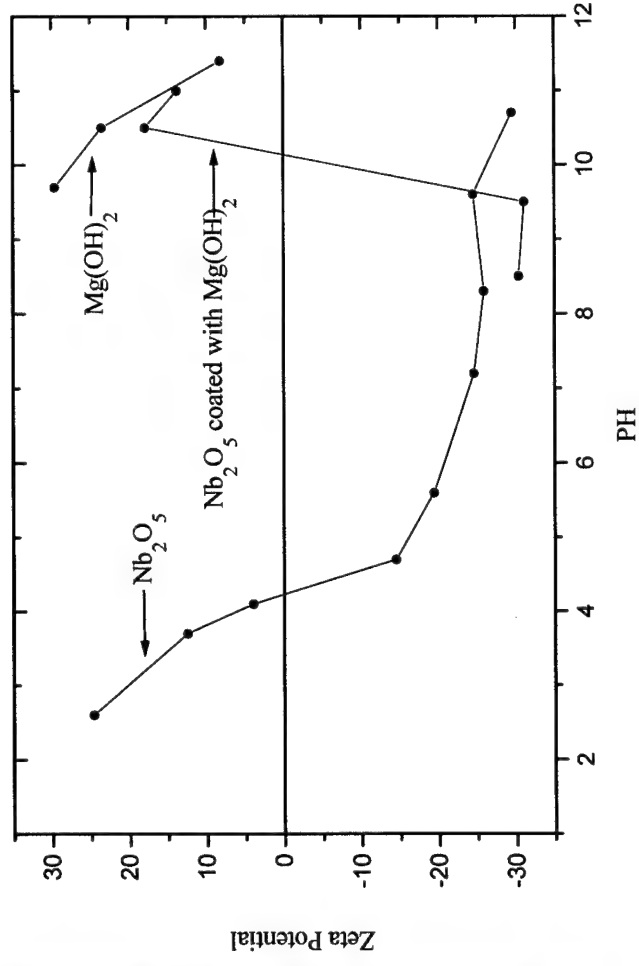
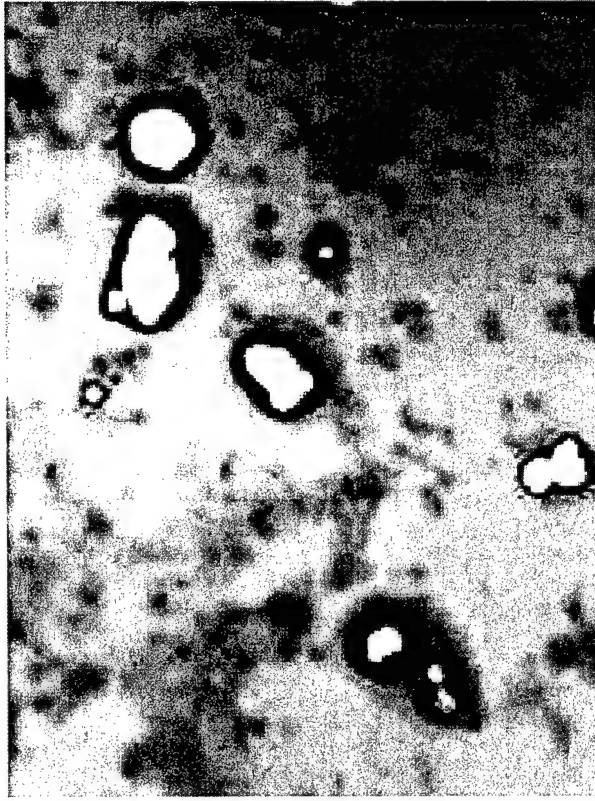


S. L. Swartz and T.R. Shrout, *Mater. Res. Bull.*, Vol 17, 1245-1250,  
(1982).

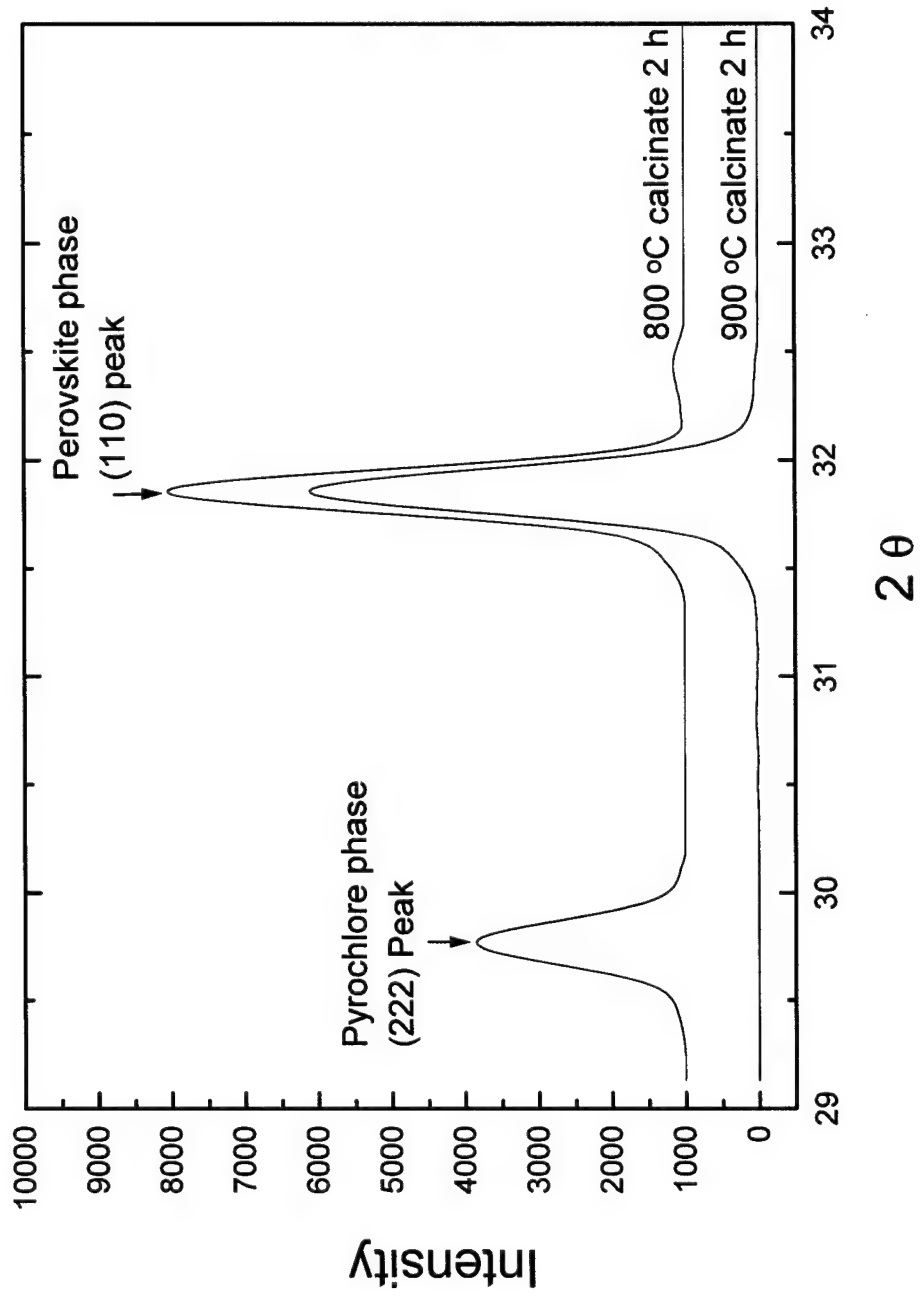
Our approach: Coating of  $\text{Nb}_2\text{O}_5$  powder with  $\text{Mg}(\text{OH})_2$ , to prevent the interaction between  $\text{Nb}_2\text{O}_5$  and  $\text{PbO}$ .



# Coating of $\text{Mg}(\text{OH})_2$ on $\text{Nb}_2\text{O}_5$

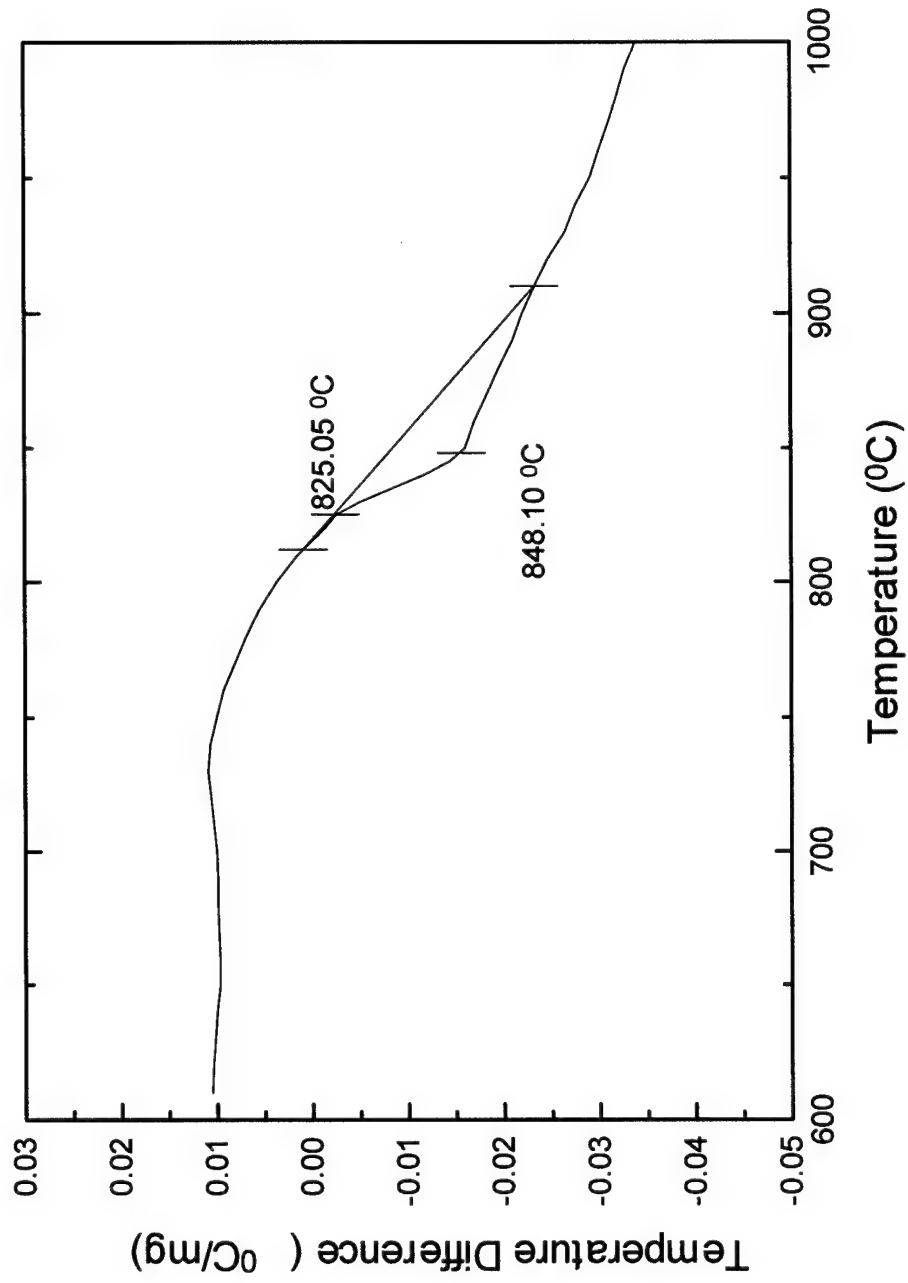


# Pyrochlore-free, Perovskite 0.9PMN-0.1PT

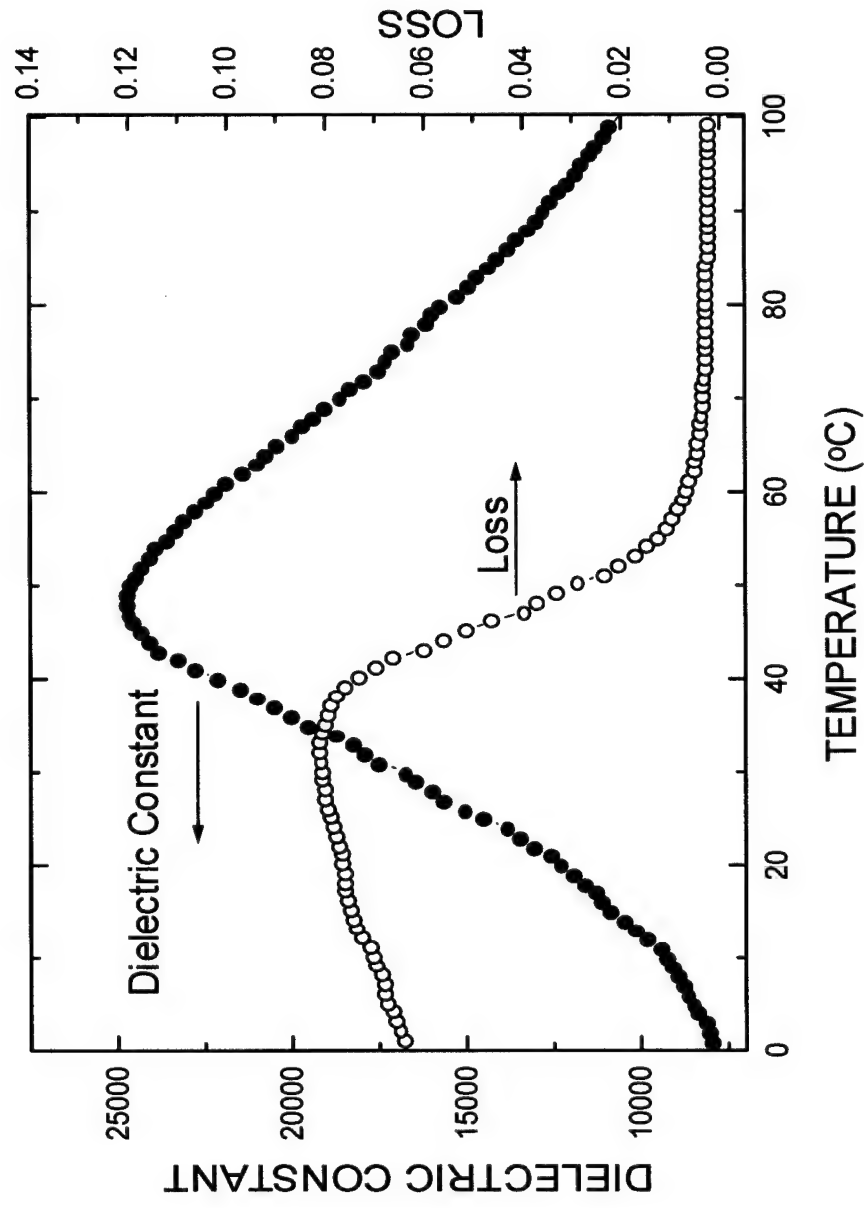




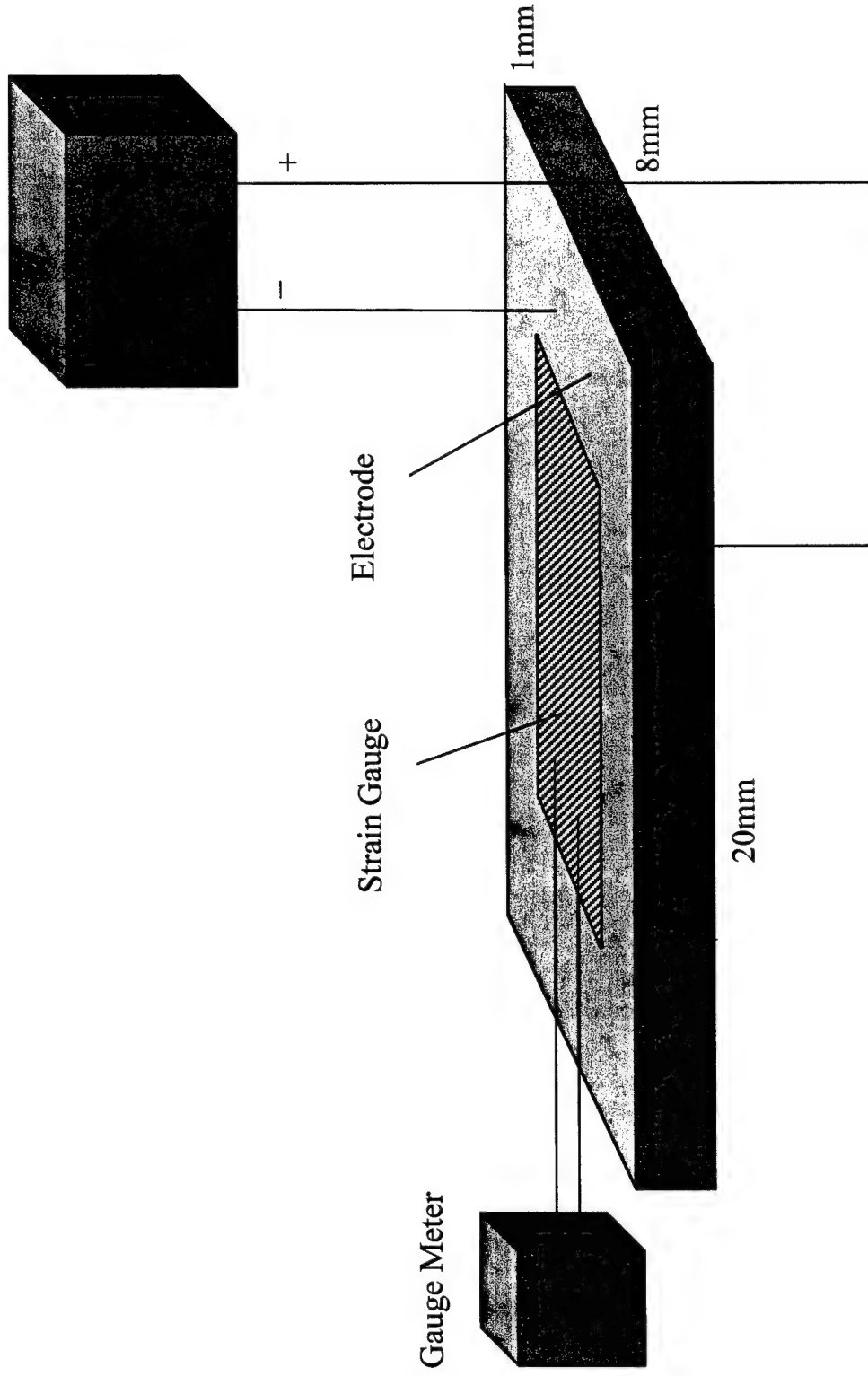
# DTA



# Dielectric constant $\sim 24,660$ at $T_c$

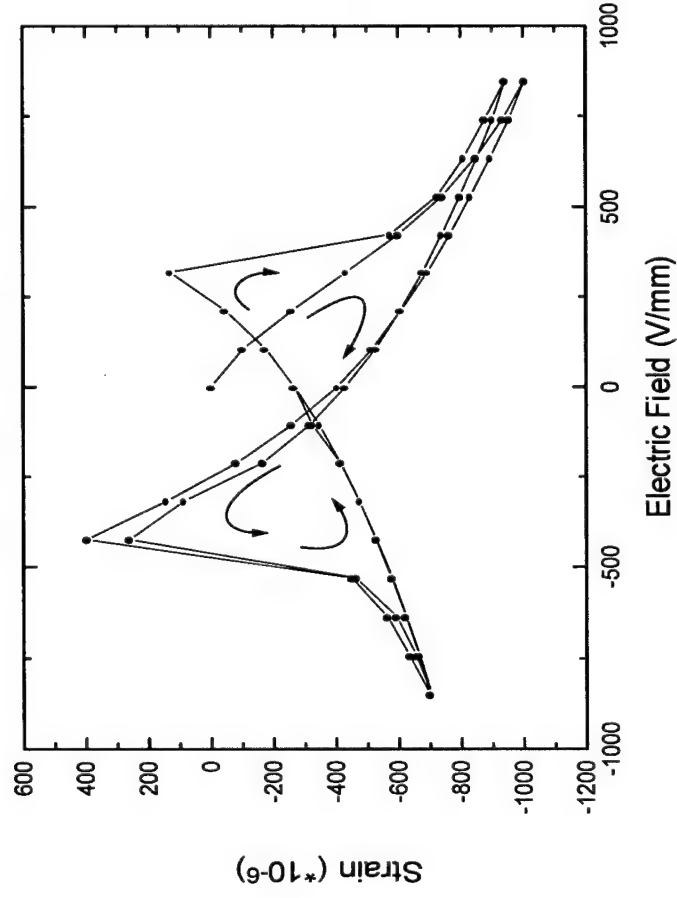


High Voltage Generator

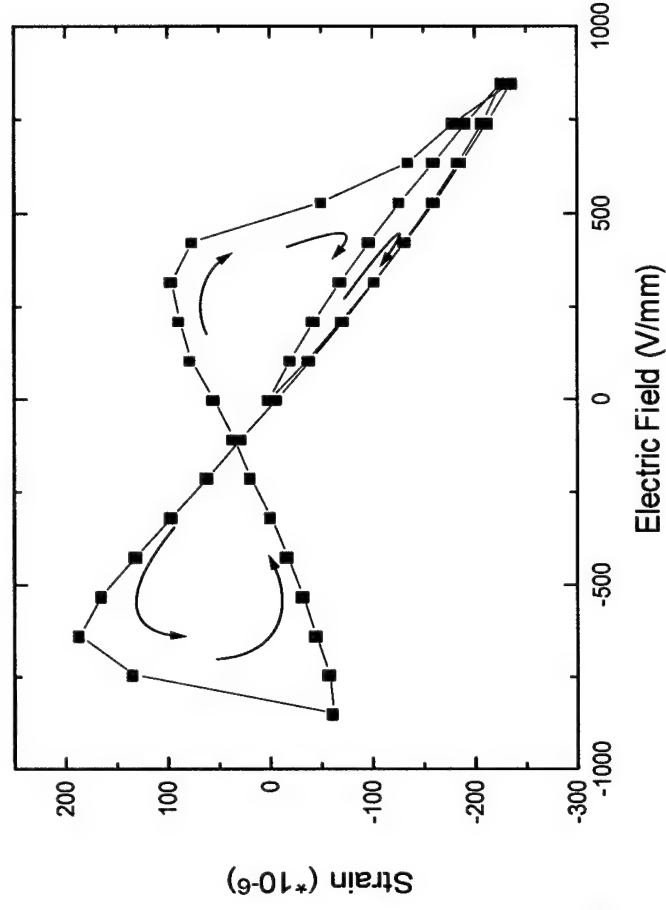


# Strain vs. Electric Field Behavior

EDO powders

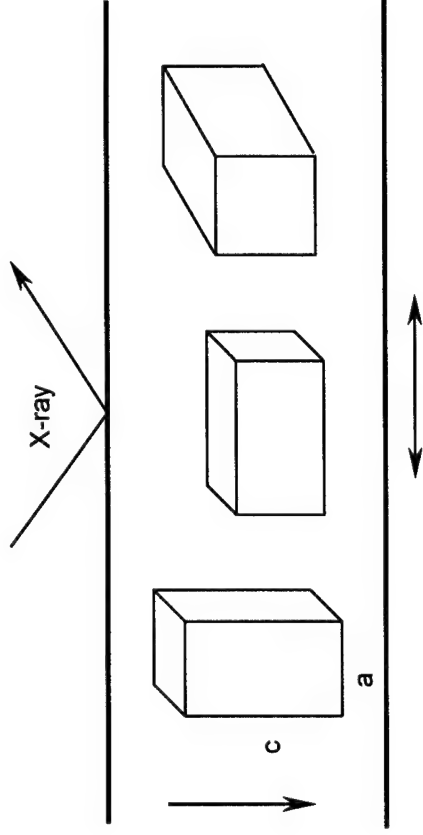


0.6PMN-0.4PT

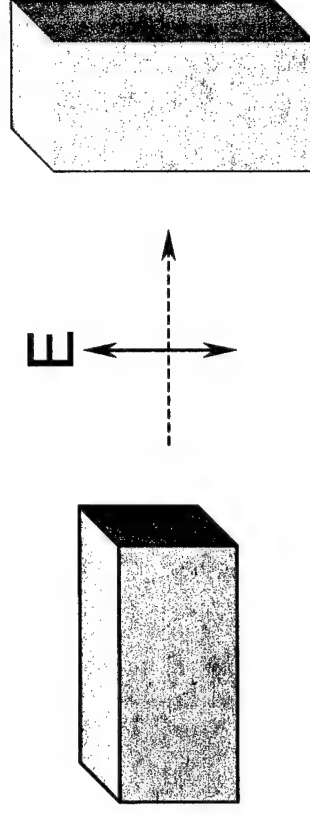
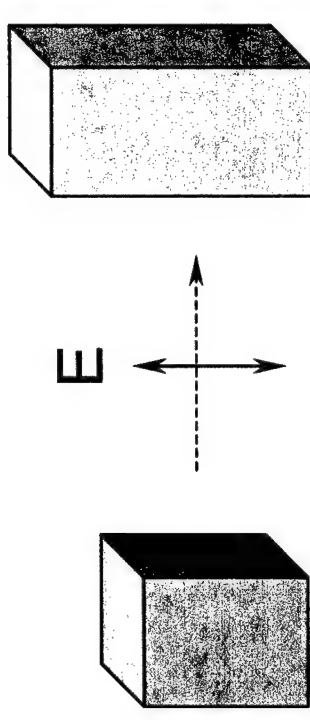


## Summary of Properties

	$d_{33}$ ( $10^{-12}$ m/v)		$d_{31}$ ( $10^{-12}$ m/v) at 800V/mm	Dielectric Constant at room temperature
	At low electric field	At Electric Field of 800 V/mm		
EDO Powder	468.8	7000	1180	4735
0.6PMN-0.4PT	336	Not able to detect	267	3408

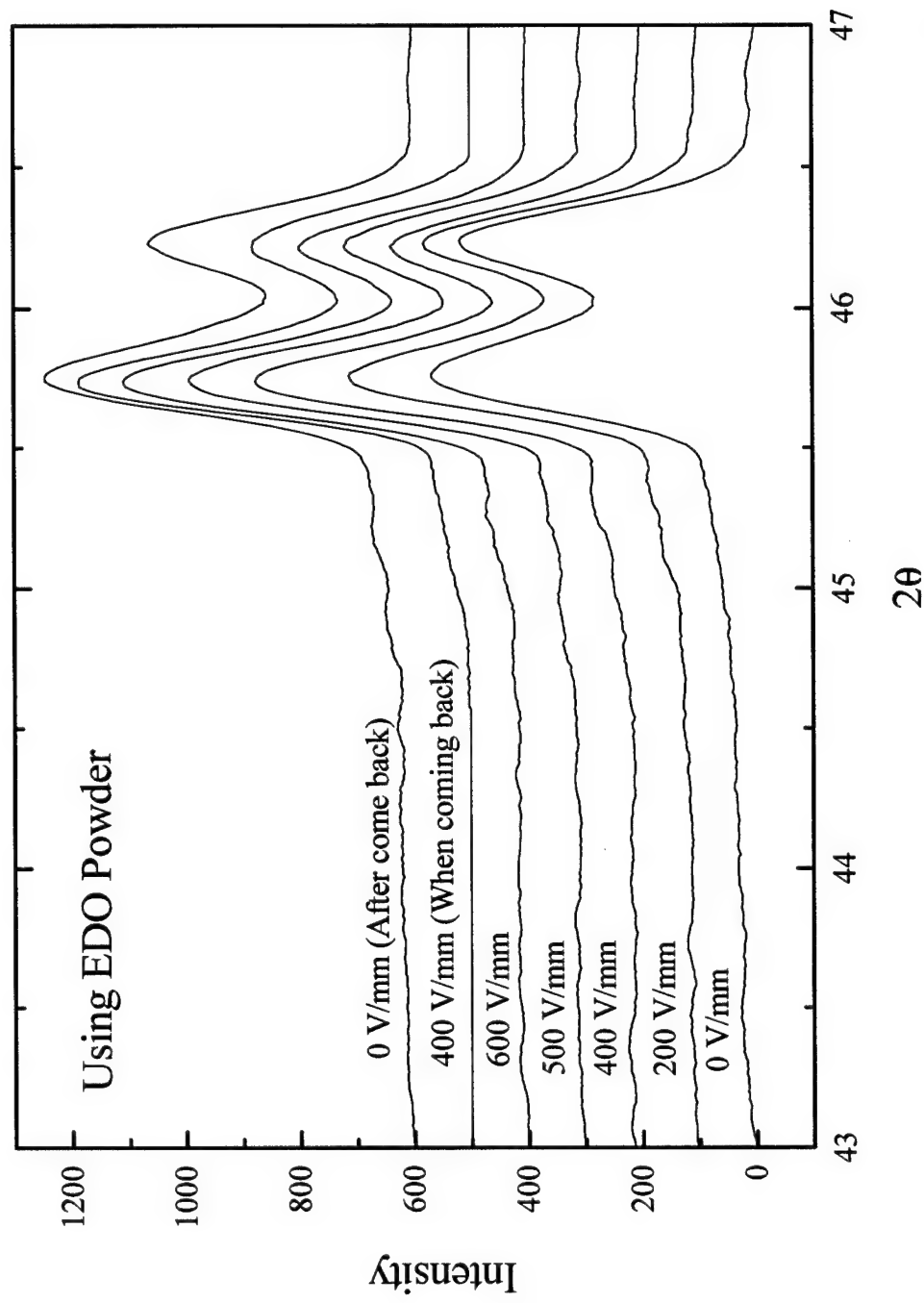


Piezoelectric effect  
c and a change with E

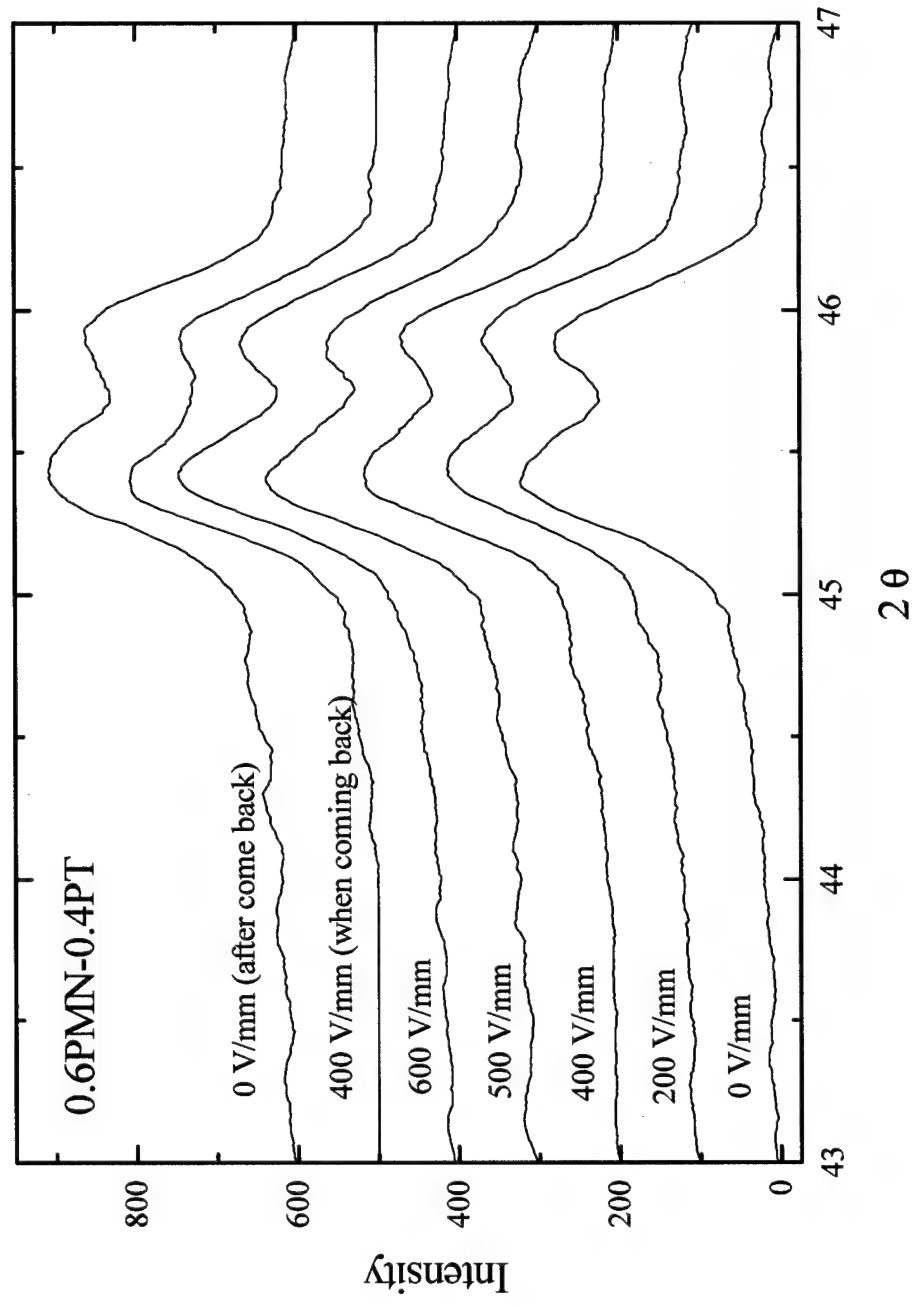


90° Domain switching  
 $I_{(002)}/I_{(200)}$  changes with E

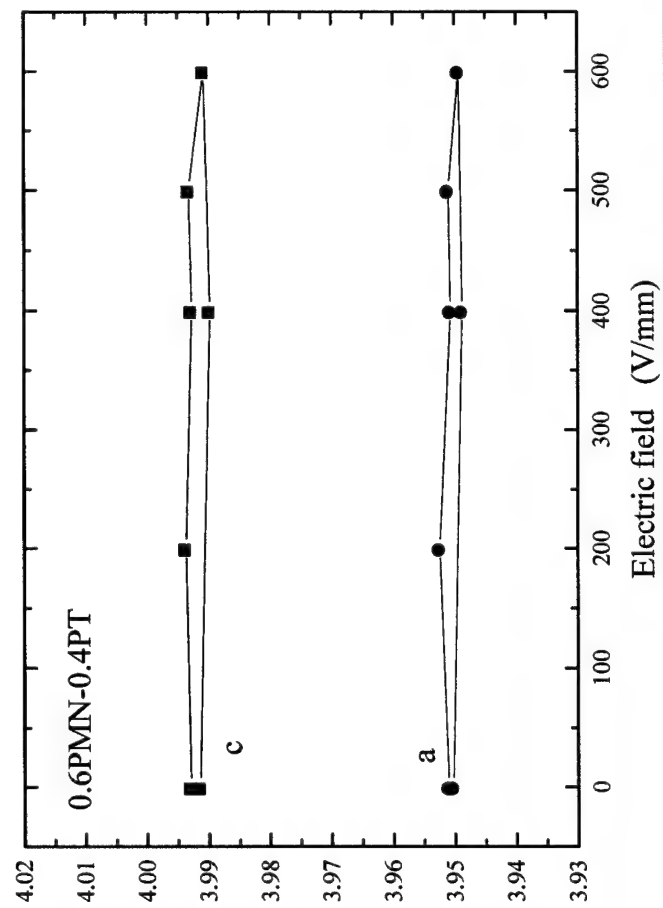
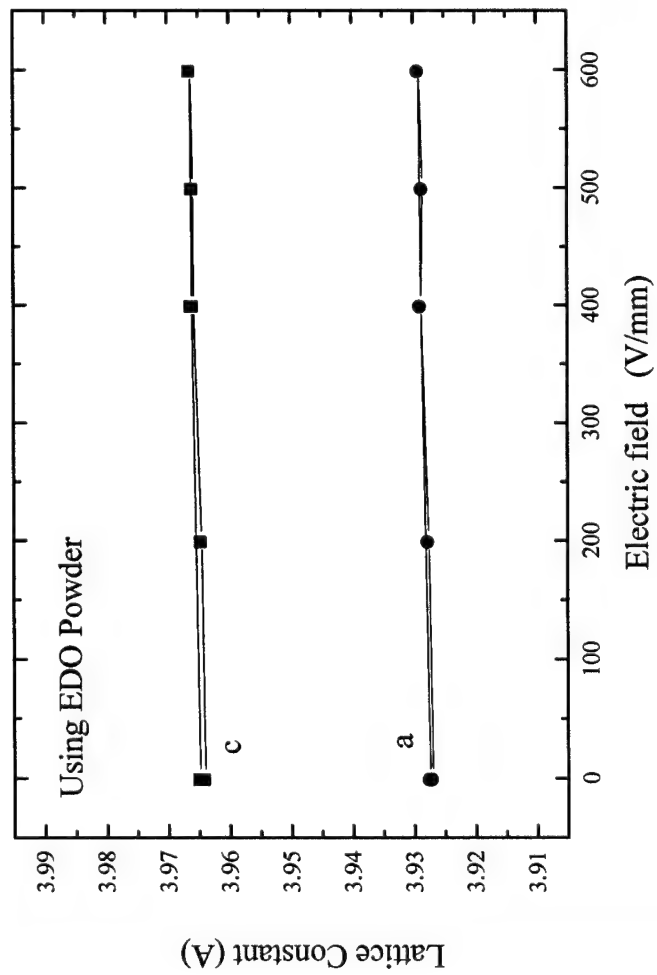
# XRD patterns with Electric Fields



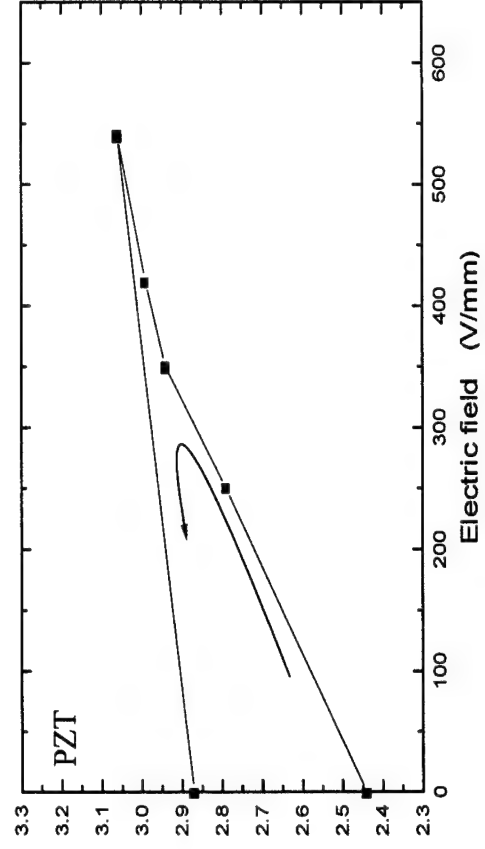
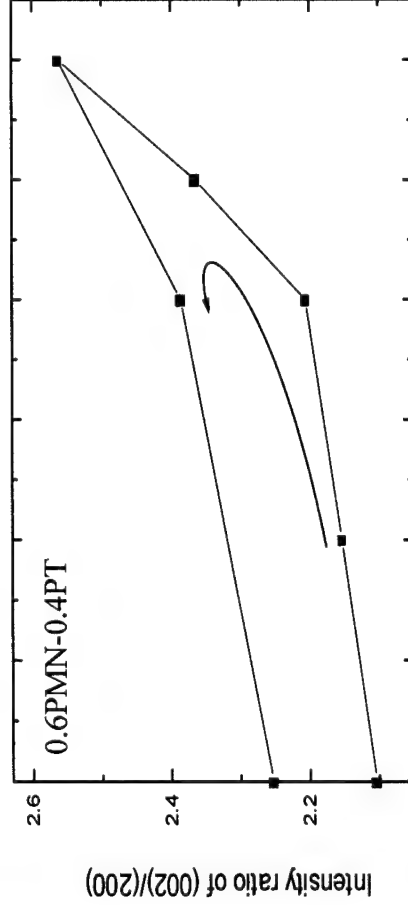
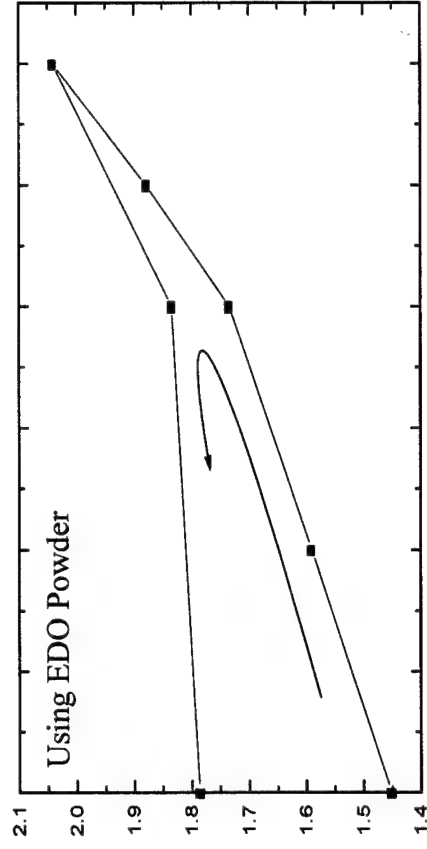
# XRD patterns with Electric Fields







# Domain switching



$$R(0) = \frac{I_{0(002)}}{I_{0(200)}} = \frac{C}{A} \quad R(E) = \frac{I_{(002)}}{I_{(200)}} = \frac{nA + C}{(1-n)A}$$

$$n = \frac{R(E) - R(0)}{1 + R(E)}$$

n = fraction of a-domains switched to c-domains

$$S_{1, domain}(E) = \frac{L(E) - L(0)}{L(0)}$$

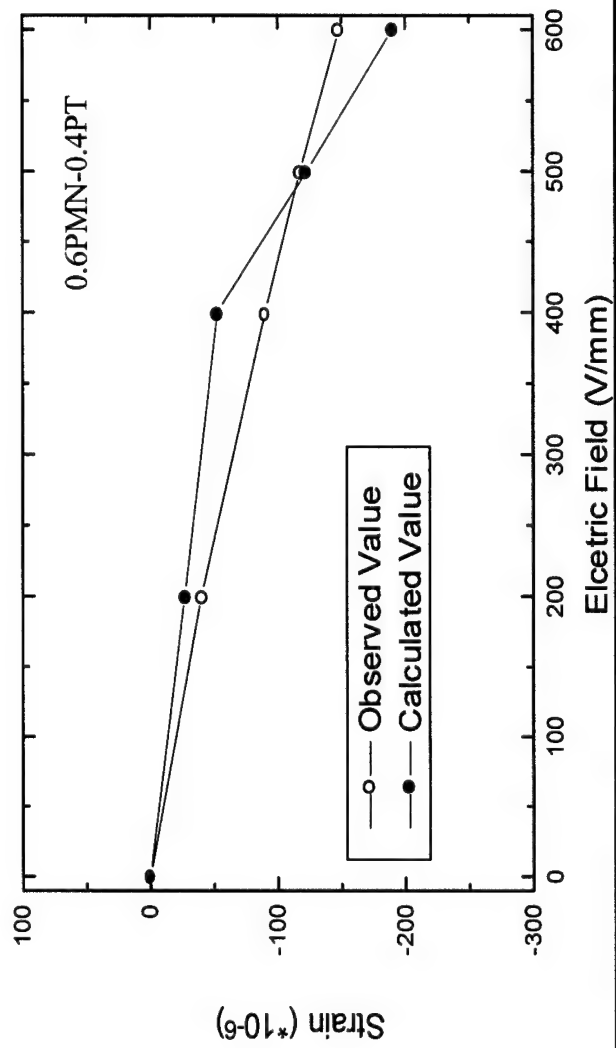
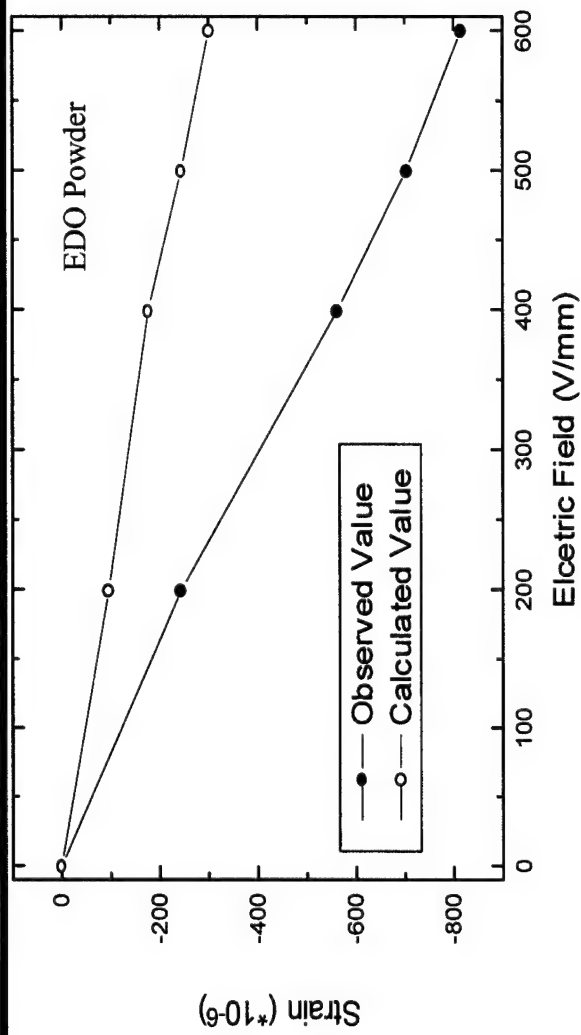
$$L(0) = \eta(0)Ac + (1 - \eta(0))Aa + Ca$$

$$L(E) = \eta(E)(1 - n)Ac + (1 - \eta(E))(1 - n)Aa + (C + nA)a$$

Assuming  $\eta(0) = \eta(E) = 1/2$ ,

$$S_1(E) = \frac{(c - a)[R(0) - R(E)]}{[1 + R(E)][c + a + 2aR(0)]}$$

---



## Conclusions

- *A one-step heating process using  $\text{Mg}(\text{OH})_2$ -coated  $\text{Nb}_2\text{O}_5$  powders and  $\text{PbO}$  was developed for synthesizing perovskite PMN-PT*
  - *0.6PMN-0.4PT shows significant domain switching behavior at high electric fields*
  - *EDO powders show very high  $d_{33}$  and  $d_{31}$  values at 800 V/mm indicating PMN-PT has great potential for actuator and sensor applications*
-

# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***Stereolithography of Organic/ Inorganic Composites***

**ROBERT K. PRUD'HOMME<sup>\*,§</sup>, ILHAN A. AKSAY<sup>\*,§</sup>, DAVID L. MILIUS<sup>\*,§</sup>,  
JAMES S. VARTULI<sup>\*,§</sup>, RAJEEV GARG<sup>\*,§</sup>, AARON J. DULGAR<sup>\*,§</sup>,  
PETER J. PHOTOS<sup>\*,§</sup>, JAMES LEE<sup>\*,§</sup>, JAMES LIANG<sup>\*,§</sup>**

**DEPARTMENTS OF \*CHEMICAL ENGINEERING, #PHYSICS, AND  
§PRINCETON MATERIALS INSTITUTE  
PRINCETON UNIVERSITY, PRINCETON, NEW JERSEY 08544**

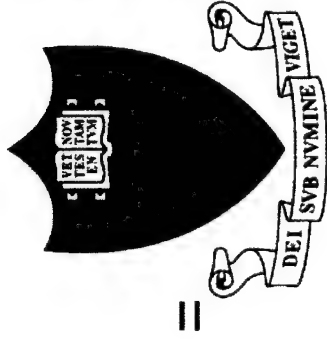
**†DEPARTMENT OF CHEMISTRY, HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS 02138**

**‡DEPARTMENT OF PHYSICS, CORNELL UNIVERSITY  
ITHACA, NEW YORK 14853**

## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**



Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

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# Rapid Prototyping of Polymer/Ceramic Composites

Robert K. Prud'homme, Ilhan A. Aksay,  
Rajeev Garg, Jim H. Lee, Jim Liang,  
David L. Milius, Aaron J. Dulgar, and Peter J.  
Photos

Department of Chemical Engineering and  
Princeton Materials Institute,  
Princeton University, Princeton, NJ 08544

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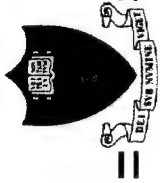


## Introduction

- ***Goal: Fabrication of ceramic/polymer composites***
- ***Case study: bone implants***
  - Stereolithography
  - Biocompatible and mechanically compatible
- ***Problems with present bone graft materials:***
  - Autogenous: limited supply, morbidity
  - Allograft: immunogenicity, viral transmission
  - Commercial products: lack bone inductivity and/or strength

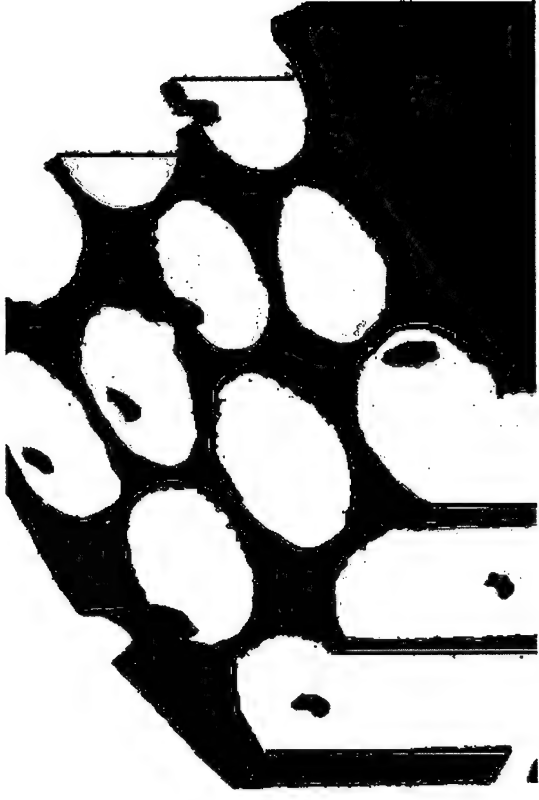
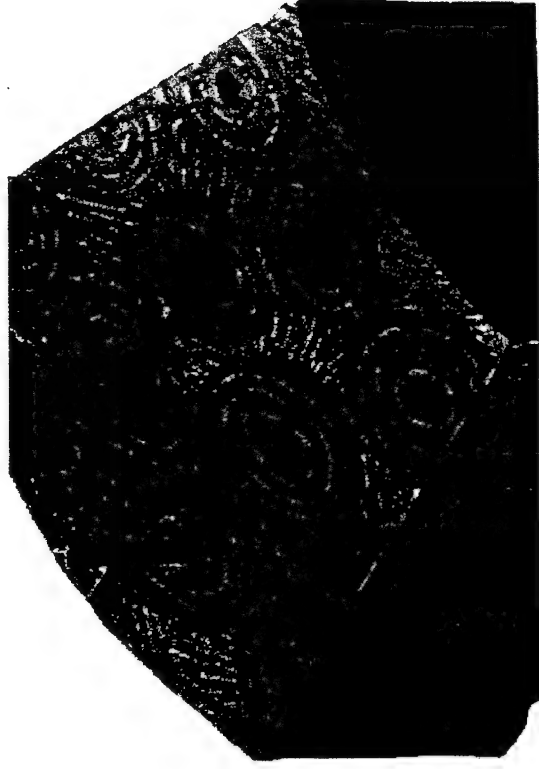




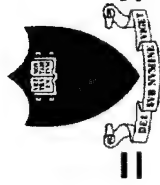


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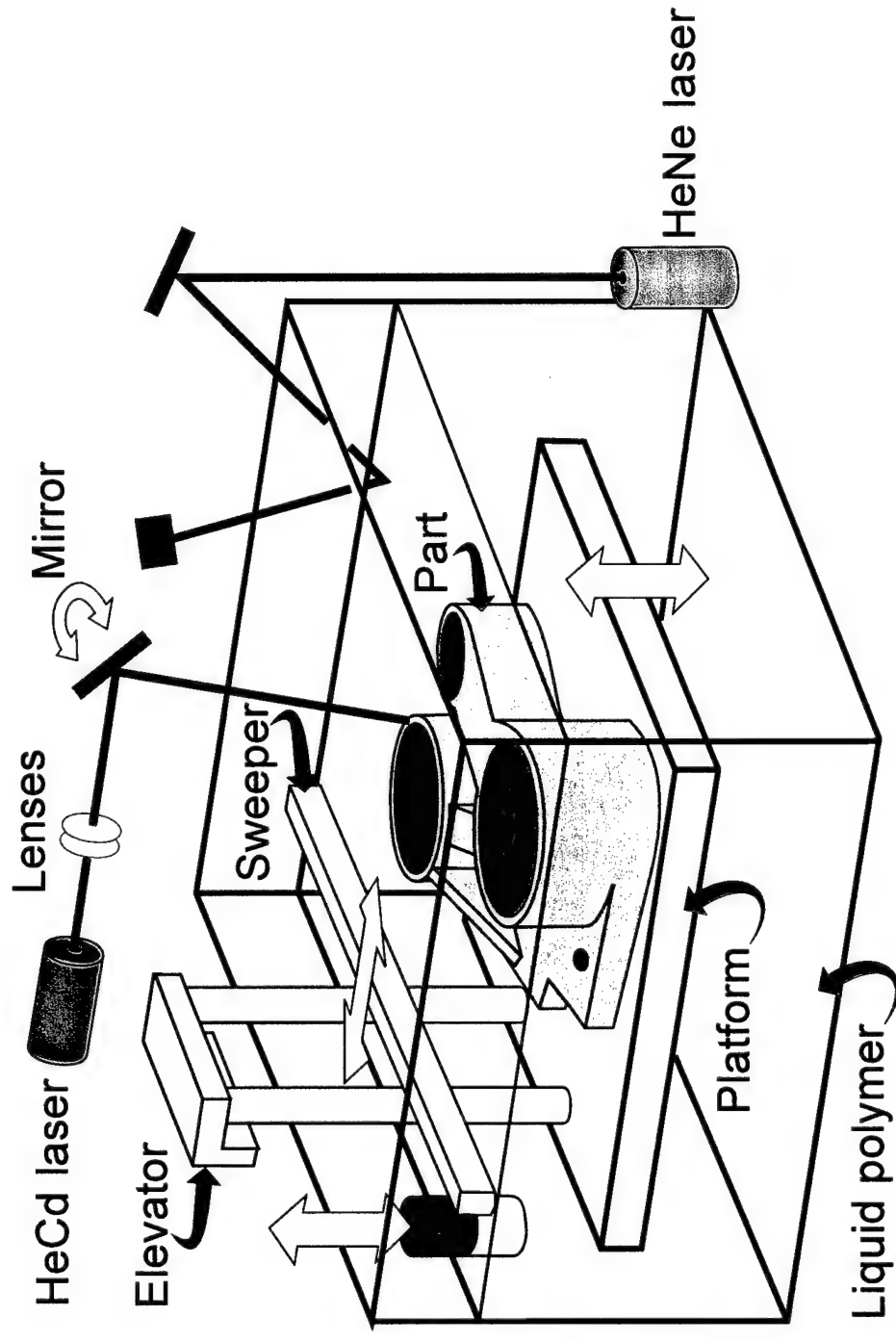
# Microstructure of Cortical Bone



L. L. Hench and J. Wilson, *An Introduction to Bioceramics*  
(World Scientific Press, NY 1993)



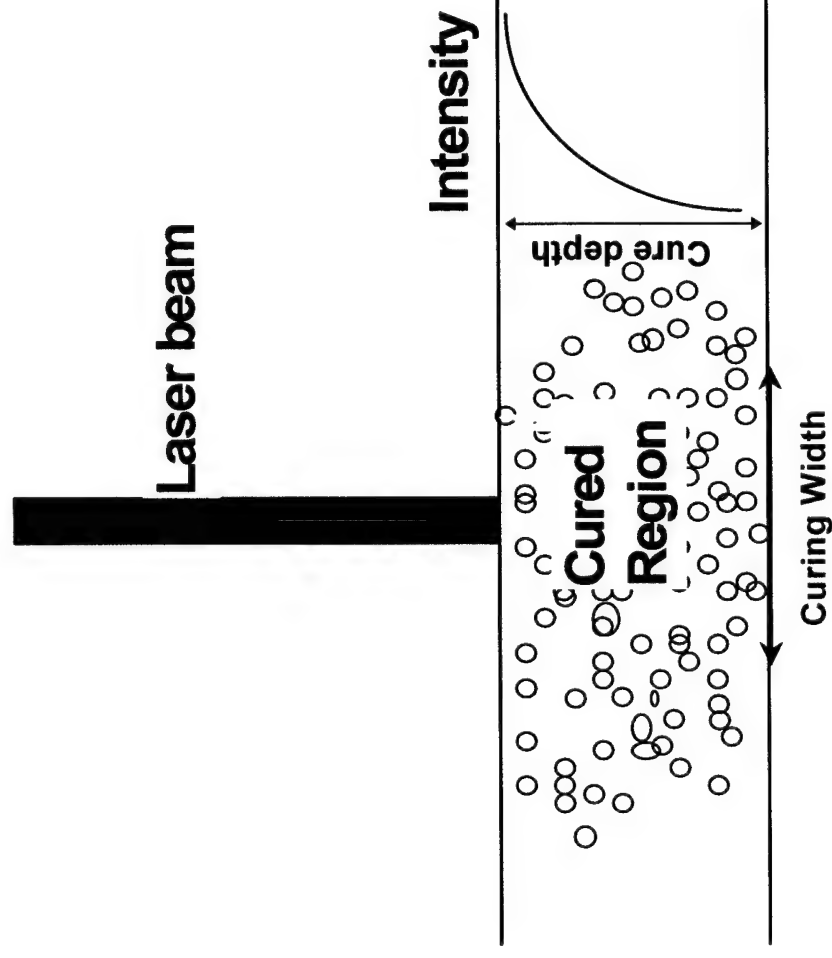
# Stereolithography

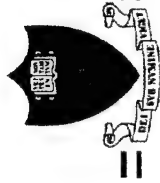




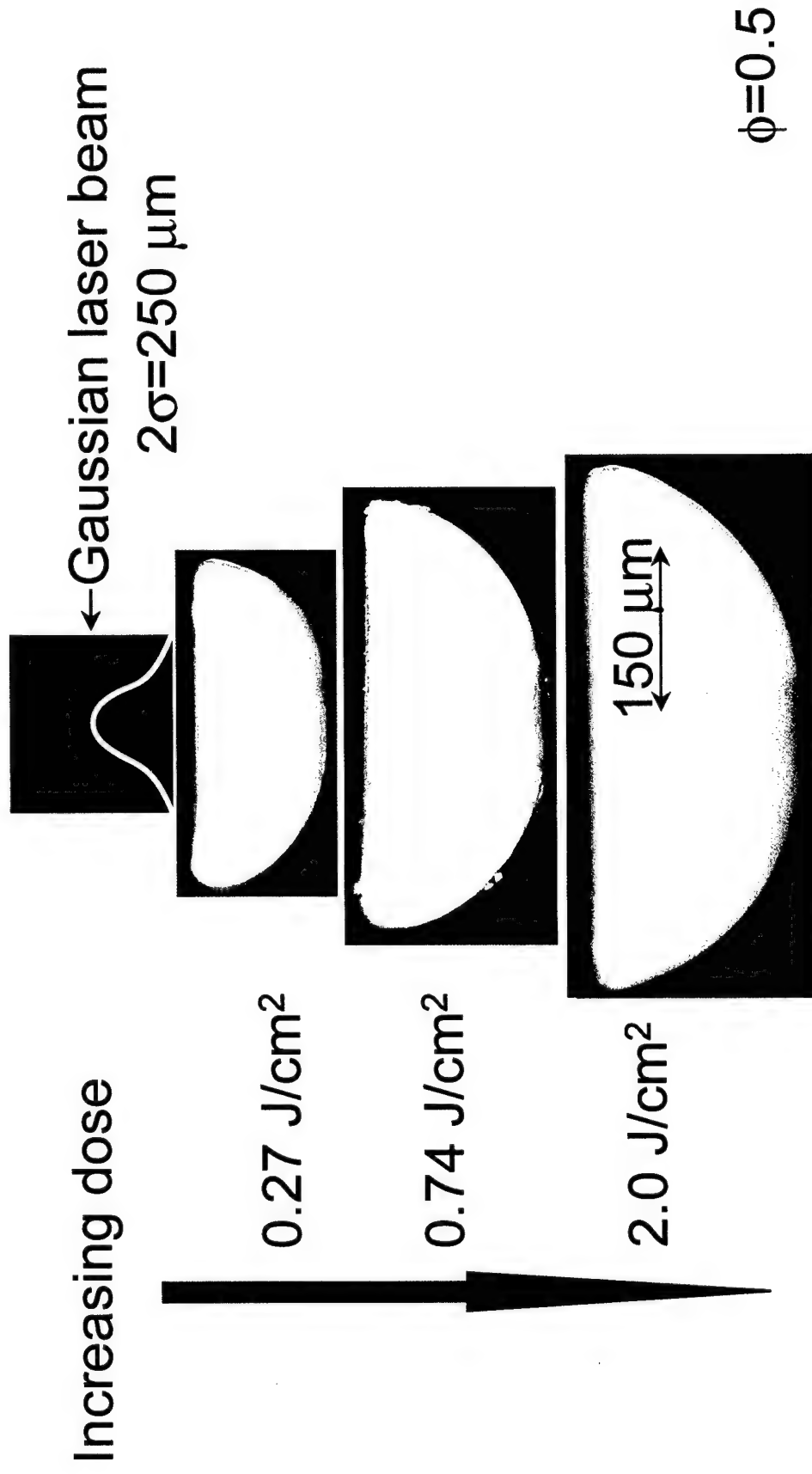
## Objective

- *To be able to define the cured profile in a single layer*
- *Factors controlling curing profile:*
  - Absorption by photopolymers
  - Light scattering from particles
- *Requires a model for light propagation in concentrated dispersion*



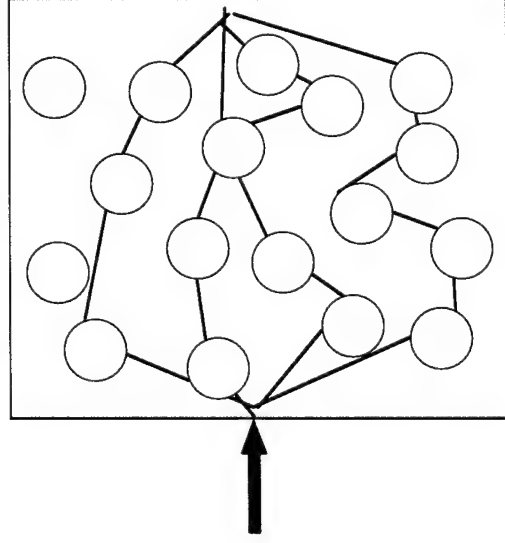


## Curing Profile





# Diffusion Model for Scattering



- **Photon Density**

$$\frac{\partial I_d}{\partial t} + D \nabla^2 I_d = f(x, y, z, t)$$

$$D = cl_{tr}/3$$

- **Transport length**

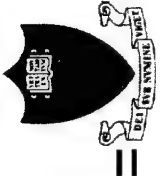
$$l_{tr} = (n\sigma_{tr}(1 - \cos(\theta)))^{-1}$$

**Photons, after going through large number of scattering events, are described as random walkers in the medium.**

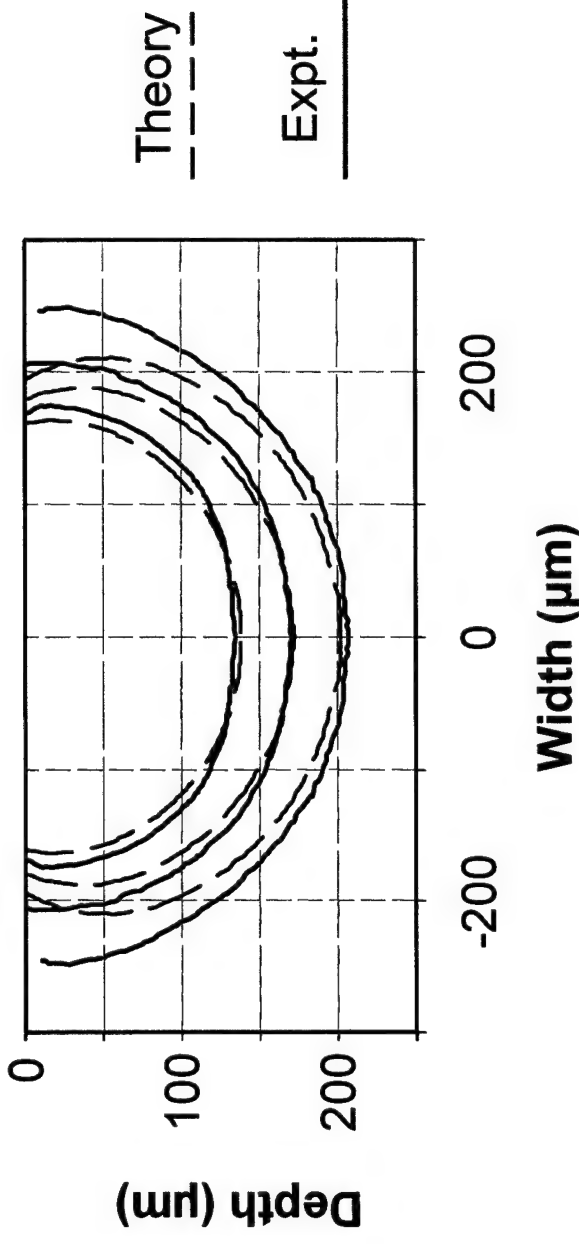
- **Correlation from PY**

$$\sigma^* = \int \frac{d\sigma}{d\Omega} (1 - \cos(\theta)) S(\theta) d\Omega$$

$$S(\theta) = 1 + n \int (g(r) - 1) e^{iq \cdot r} d^3r$$

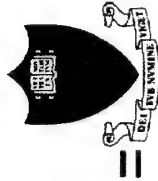


## Theory vs Experiment



Diffusion theory successfully predicts the curing profile in ceramic dispersion. The experimental profiles are compared with the profiles calculated from diffusion theory:

$$I = \frac{I_0 w^2}{4} \int_0^\infty \exp\left(-\frac{w\lambda}{2\sqrt{2}}\right)^2 J_0(\lambda r) \exp(-(\lambda^2 + D_p^{-2})^{1/2} z) \lambda d\lambda$$



## Fabricated Parts

CAT Scan/CAD File



Scan plane

Replicated Part



1 cm

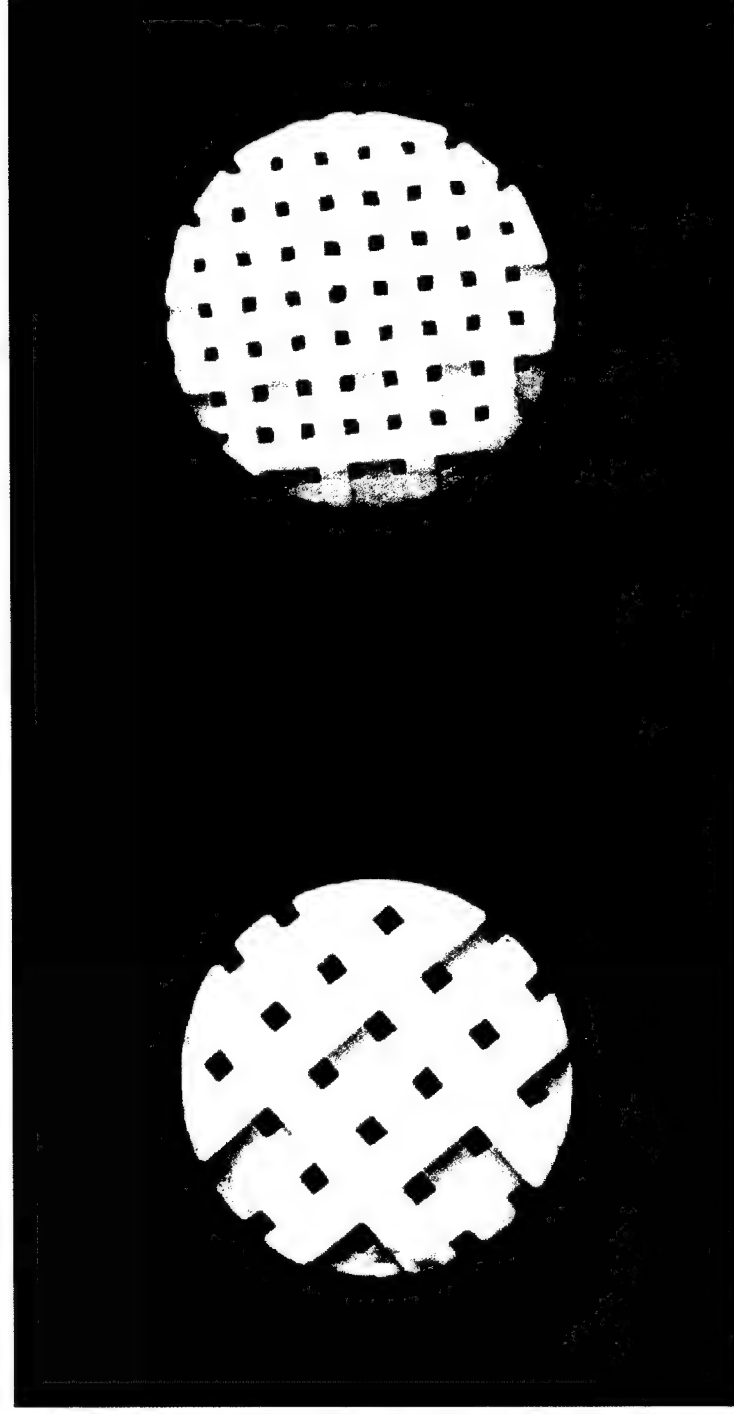
NIH VH data converted to STL file using "Materialize"  
software by Ben Dunn at Stratasy's Inc.

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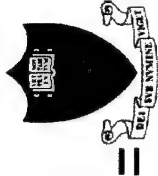


Department of Chemical Engineering and Princeton Materials Institute  
Princeton University

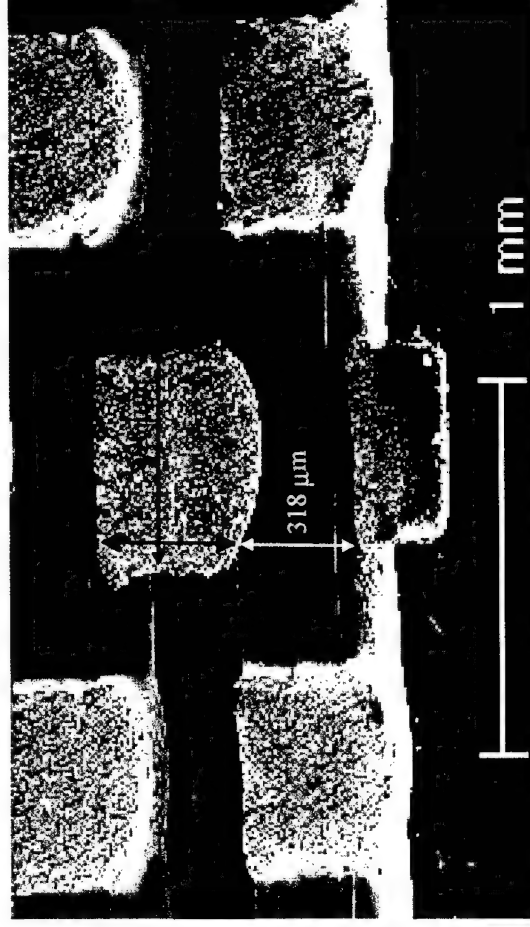
# Bone Implant Microstructure



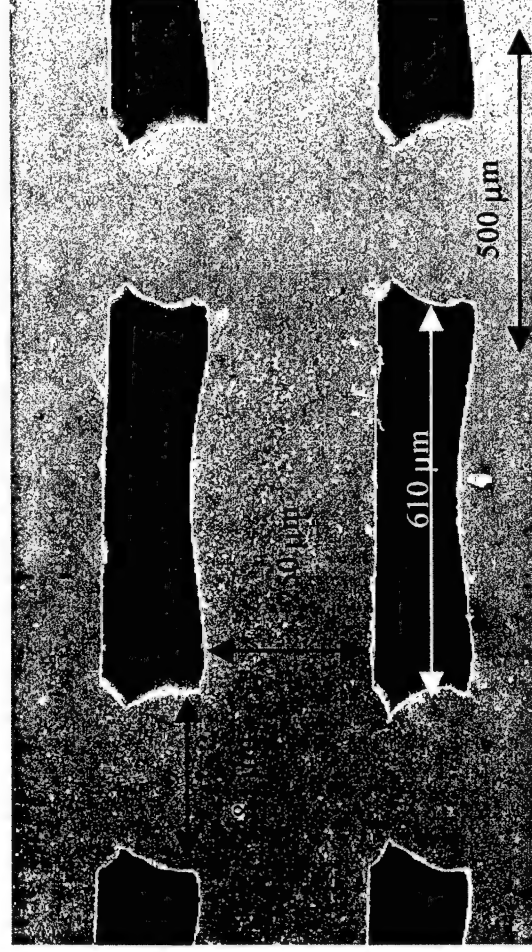




## Microstructure of Alumina Implants



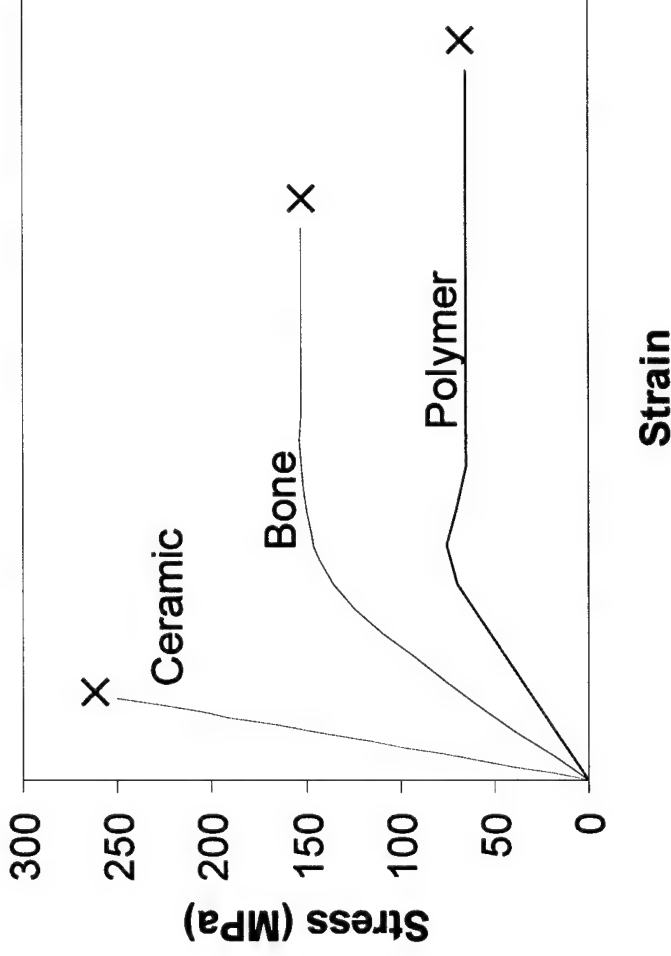
300  $\mu\text{m}$  pore size



150  $\mu\text{m}$  pore size



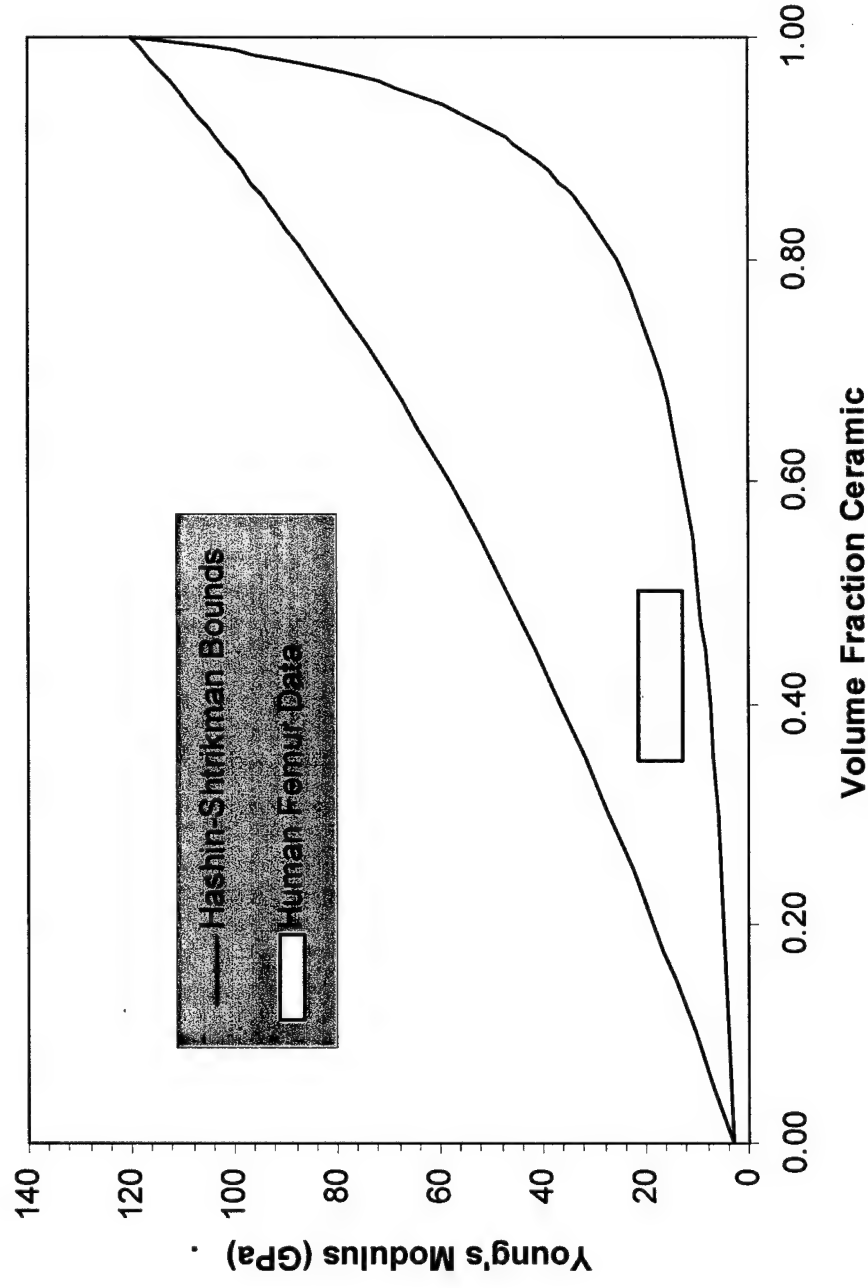
## Ceramic/Polymer Biocomposites



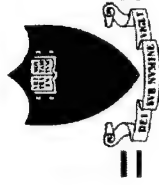
- *toughness intermediate between ceramic and polymer*
  - *composite -- 40% hydroxyapatite, 40% collagen, 20% water*
-



# Ceramic/Polymer Biocomposites



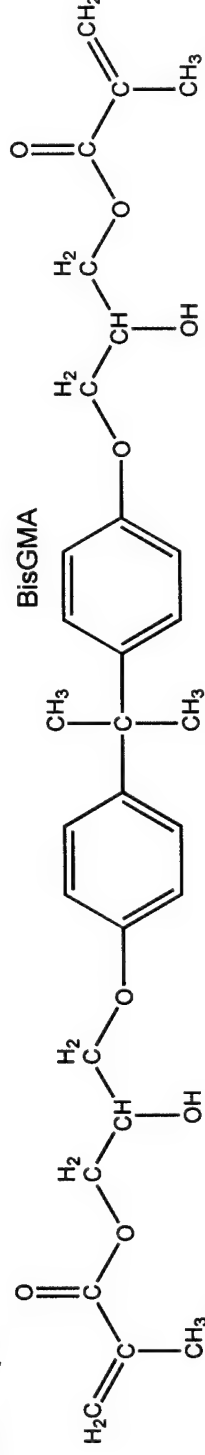
Data:  $E_p = 3$  GPa,  $E_{HA} = 120$  GPa; Currey. *Mechanical Adaptations of Bones.*



# Photochemistry

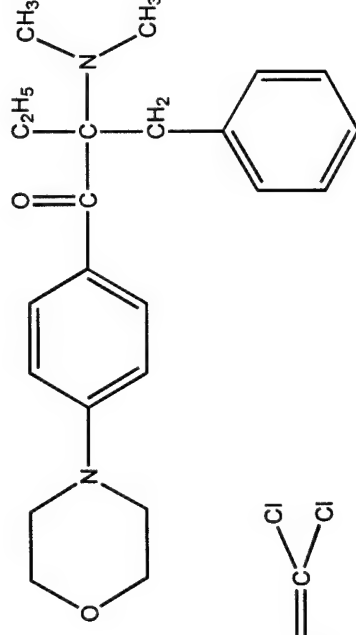
## ● Monomer

- 2,2-bis(4-(2-hydroxy-3-methacryloxypropoxy)phenyl) propane (*Bis-GMA*)



## ● Photoinitiator

- 2-benzyl-2-N,N-dimethylamino-1-(4-morpholinophenyl)-1-butanone (*DBMP*)



## ● Solvent

- trichloroethylene (*TCE*)



## Reaction Kinetics

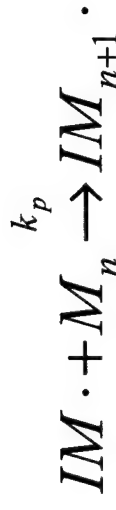
- Radical Formation



- Initiation



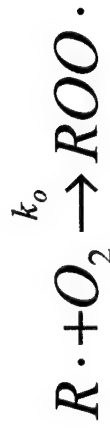
- Propagation

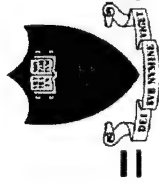


- Termination

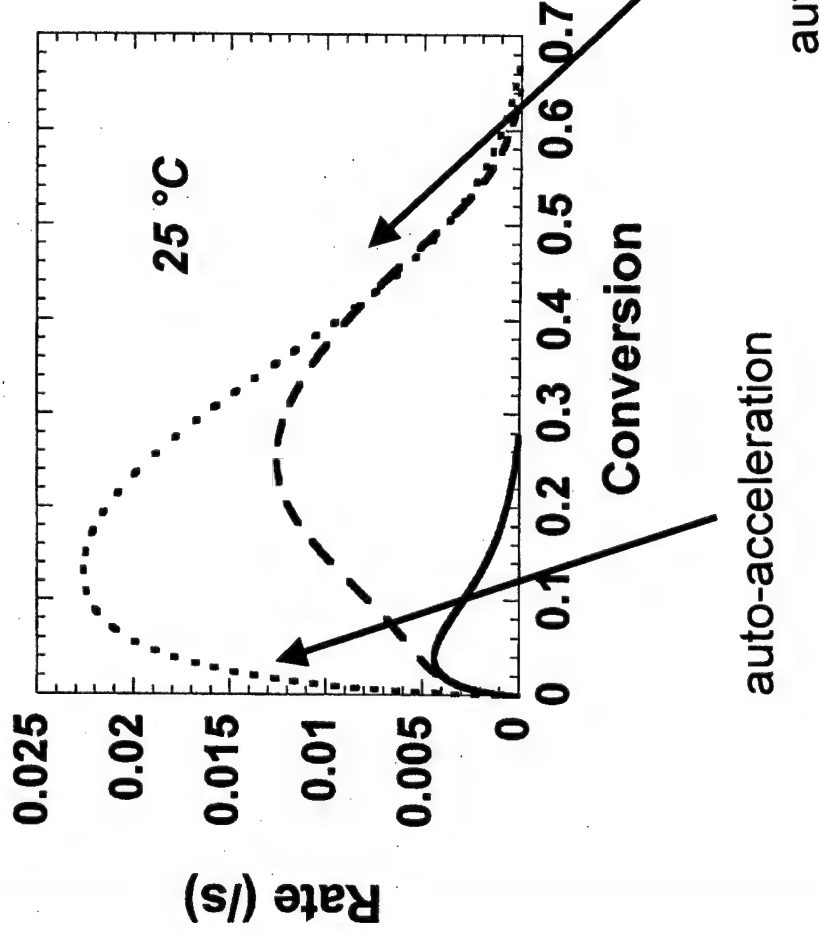


- Oxygen Scavenging





# Solvent Versus Reactive Monomer Diluent



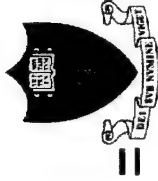
- **Solvent dilution**

- reduces initial reaction
- reduces auto-deceleration

- **Monomer dilution**

- acts as co-reactant with main monomer
- enhances auto-acceleration

Data: (-) 100% BisGMA, (--) 100% TEGDMA, (••) 50/50 BisGMA/TEGDMA; Lovell, et al. *J. of Dental Research*.



# Curing Physics

- **Energy Dosage**

**Laser beam**

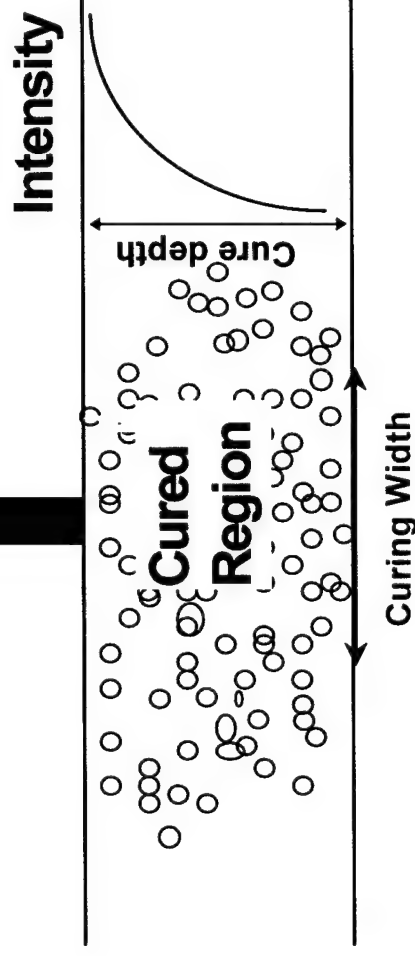
$$E(y, z) = \sqrt{\frac{2}{\pi}} \left( \frac{P_l}{\omega V_s} \right) \exp \left( -\frac{2y^2}{\omega^2} \right) \exp \left( -\frac{z}{D_p} \right)$$

- **Beer Lambert Law**

$$D_p = \frac{\log \left( \frac{I_o}{I_t} \right)}{\varepsilon [PI]}$$

- **Cure Depth Profile**

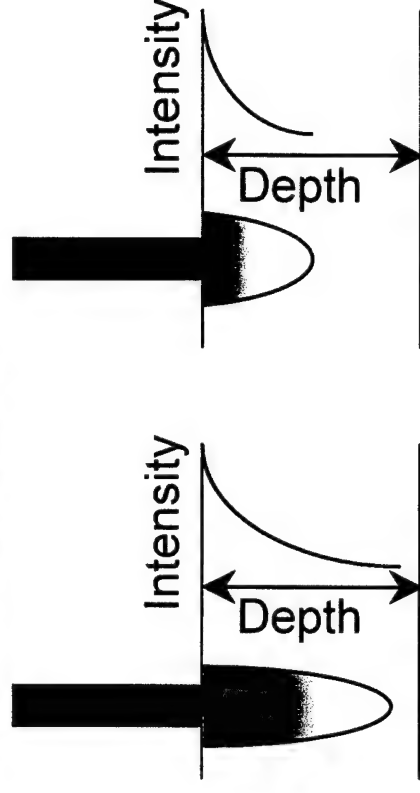
$$C_d = D_p \ln \left( \frac{E_{\max}}{E_c} \right)$$





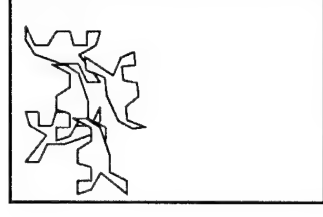
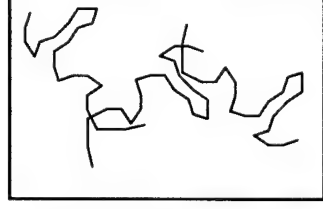
## Effect of Photoinitiator Concentration

- *Photoinitiator absorbs light and decreases laser penetration depth*
- *Radical formation proportional to laser intensity*
- *Polymerization & gelation proportional to radical concentration*
- **BALANCE:**



Low [PI]

High [PI]



■ Depth of Cure

Loose Gel

Dense Gel

■ Polymer Solids Formation

Deep Penetration

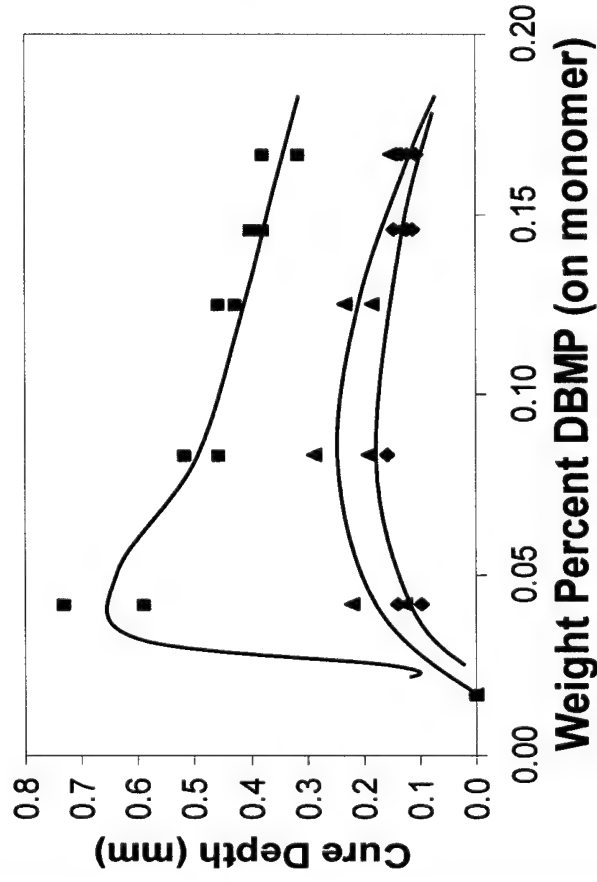
Shallow



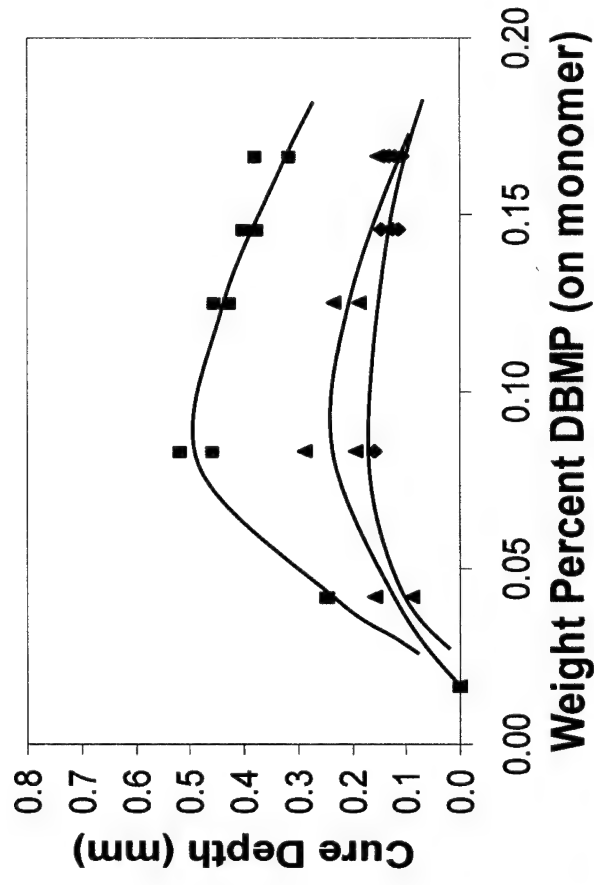


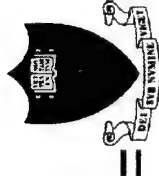
# Curing Depth Versus Photoinitiator Concentration

*Wet Gel Thickness*



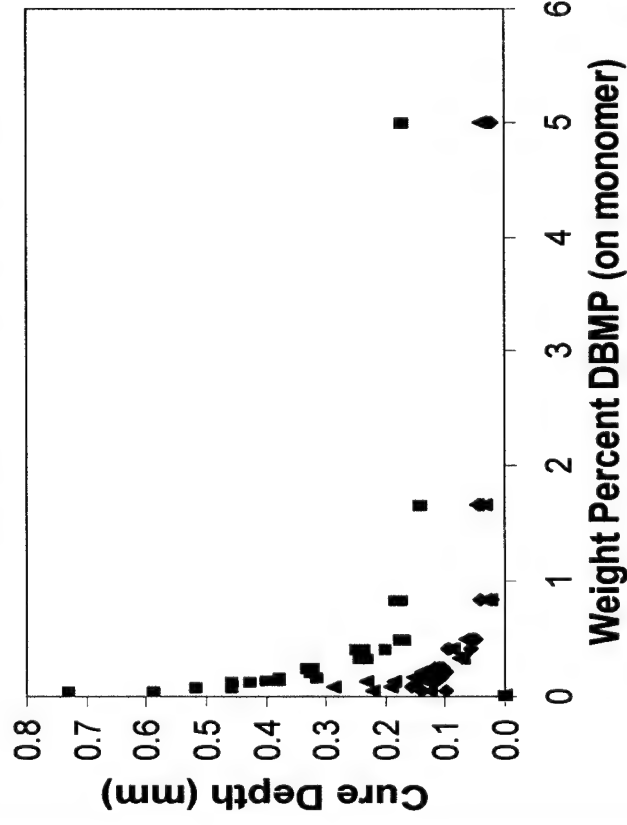
*Dry Gel Thickness*



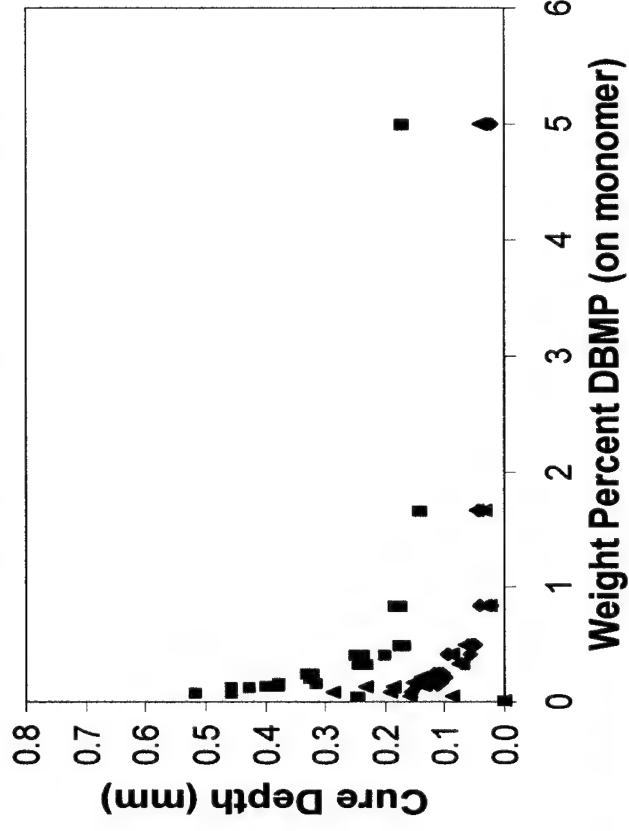


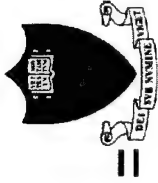
# Curing Depth Versus Photoinitiator Concentration (extended data)

*Wet Gel Thickness*



*Dry Gel Thickness*





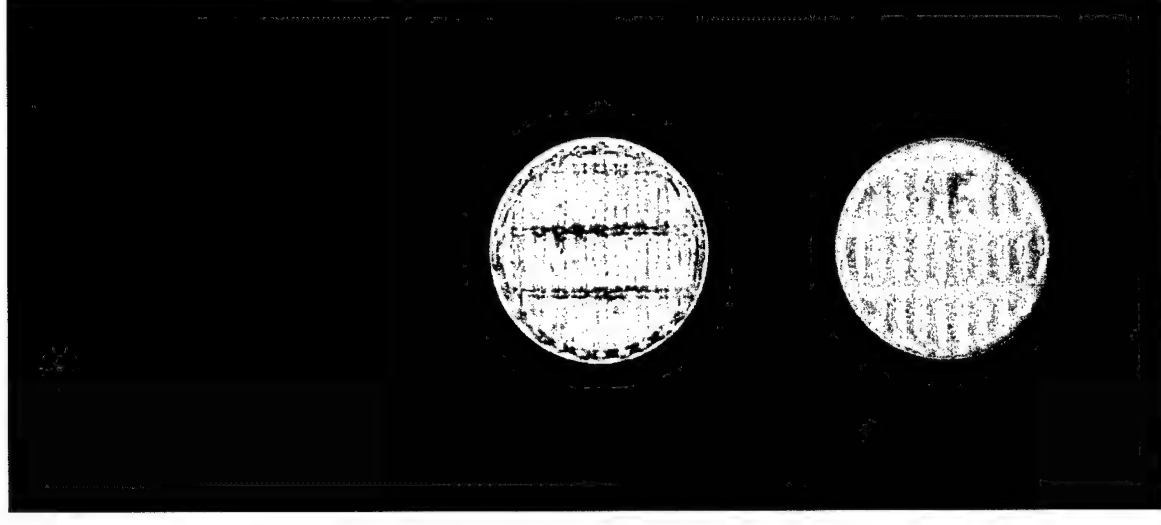
## Samples

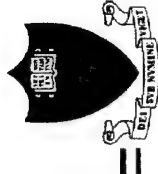
- *Design file:*

- 1 cm x-y diameter
- 250  $\mu\text{m}$  z-directional thickness

- *Single-layer BisGMA polymer*

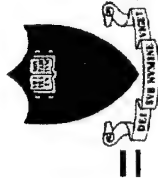
- *Single-layer BisGMA and alumina composite*





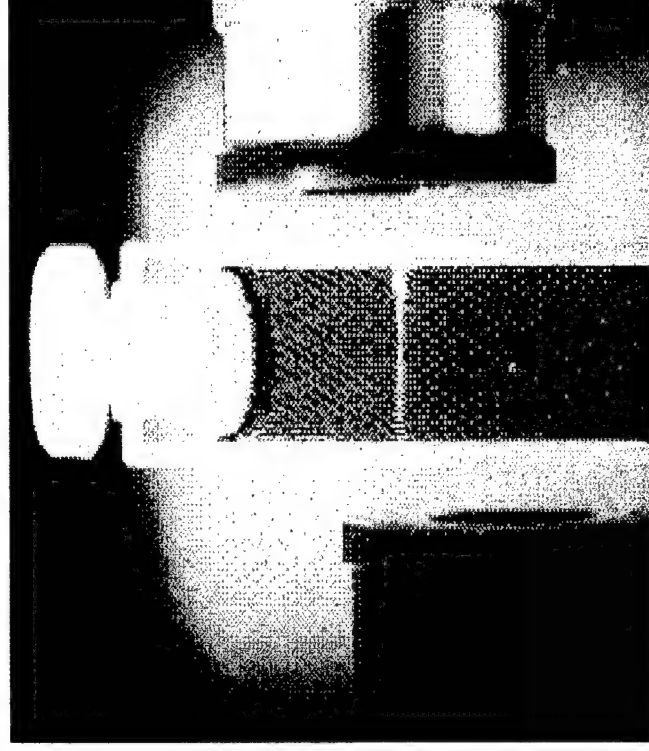
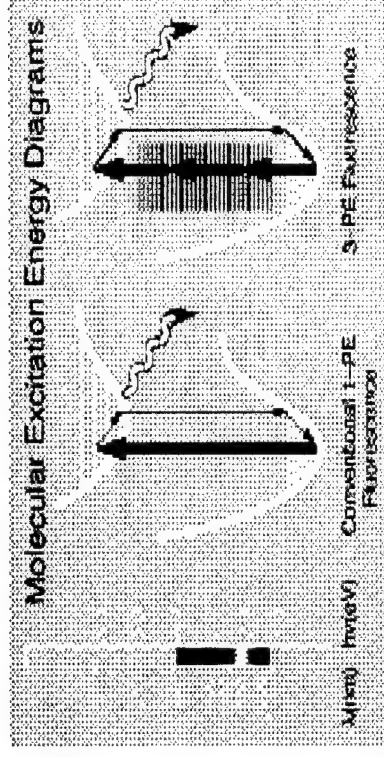
## **Future Work**

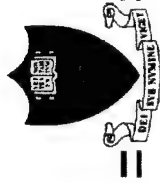
- *Fabrication of 3-D materials*
  - *Post Curing*
  - *Solvent Removal*
  - *Mechanical Properties Testing*
-



## 2-Photon Excitation Stereolithography

- *Technique from biophysics for fluorescence imaging*
- *Excitation only in regions of multiple photon excitation*
- *Dimensions of  $O(\mu\text{m})$*
- *Deep penetration*





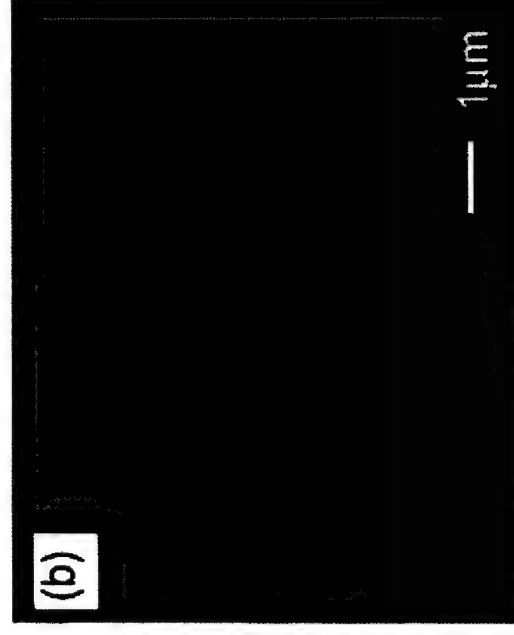
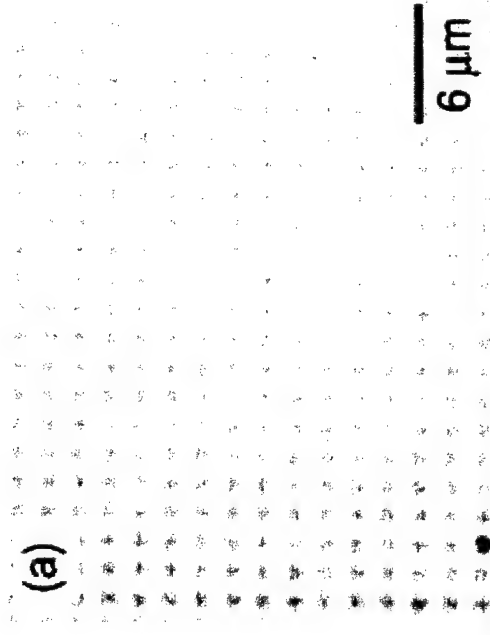
## 2-Photon Stereolithography

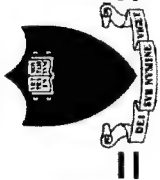
Sun et al. *App Phys Ltrs* 74 786 (1999)

### *3D pattern formation for photonic band gap structures*

- *Acrylate resin*
- *3D translation with piezo transducer*
- *1 micron features*

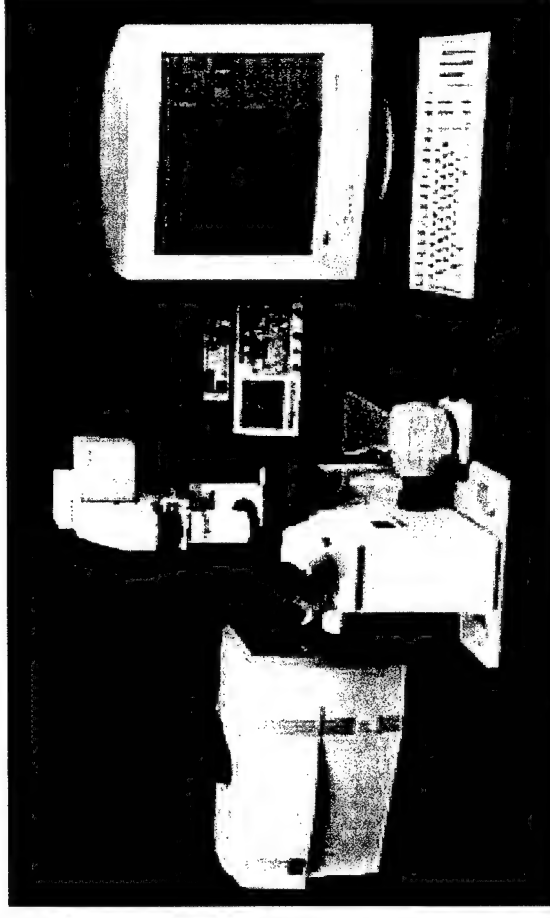
### *Continuation for ceramic materials*





## 2-Photon Instrumentation

- *Long wavelength light (700-1000nm) -non destructive single photon interactions*
- *Low scattering - deep penetration  $\sim \lambda^4$*
- *Femtosecond pulsed laser*
- *Bio-Rad, Leica, TILL*





# Conclusions

## Advanced Stereolithography

- *Polymer/Ceramic Stereolithography fundamentals*
    - Curing profiles for composites
    - Post curing densification
  - *3D micro Stereolithography*
    - 2-photon instrumentation (purchase with ARO funds)
    - Extension to ceramics and ceramic composites
-



# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***Mesosopic Composites as Small Materials Systems***

**GEORGE M. WHITESIDES**

**DEPARTMENT OF CHEMISTRY, HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS 02138**

## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

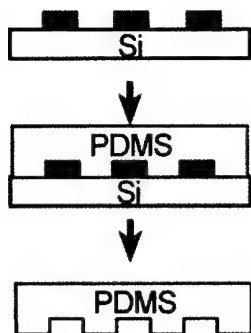
**SEPTEMBER 28 - 29, 1999**

**MURI Program Review  
Harvard University  
September 28, 1999**

*Agenda for Whitesides Group Presentation*

Introduction	George Wh
Soft Lithography	Kateri Paul
Rapid Prototyping using Soft Lithography	Tao Deng
Methods for the fabrication of small, functional structures	
Metals:	
Microorigami	Scott Brittai
Trusses	Scott Brittai
Slot Filters	Kateri Paul
Heat Exchangers	Francisco A
Composites	Francisco A
Self-Assembly of 3D Circuits	David Graci
Microcontact Printing on Curved Surfaces	Hongkai Wu
Microfabrication of Complex Geometries	Hongkai Wu
FLO for Fabrication of Microelectrode Systems	Paul Kenis
Ceramics, etc.:	
C/Si	Scott Brittai
Si/B/C/N	Hong Yang
General Methods	
Metals:	
Microelectrochemistry:	
Applications for non-planar surfaces	Scott Brittai
Rapid Prototyping Using Silver Halide Film	Tao Deng
3D Microfabrication in Microfluidic Systems	Janelle And
Self-Assembly of Microstructures	Tom Clark
Polymers:	
Dali Crosses	Hong Yang
Future Directions	Kateri Paul

# Techniques of Soft Lithography

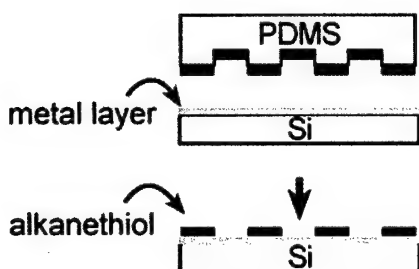


Master: prepared by photolithography, micromolding, or other techniques

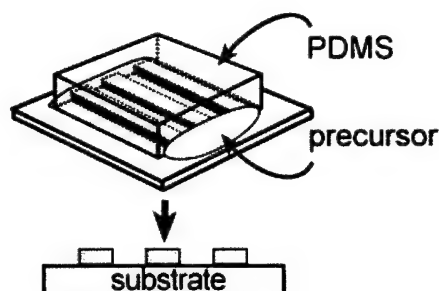
Pour prepolymer and cure

Remove stamp

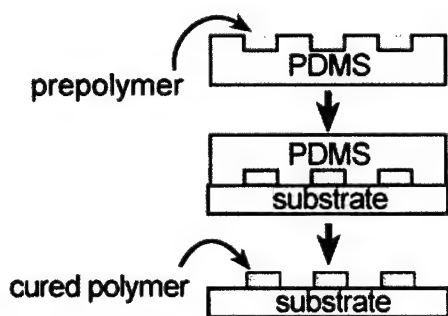
## Microcontact printing



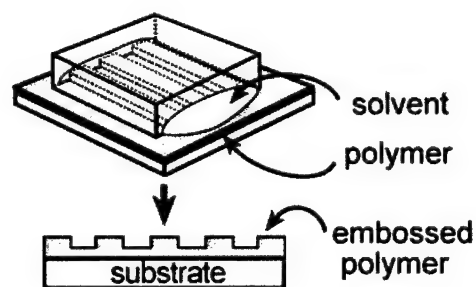
## Micromolding in capillaries



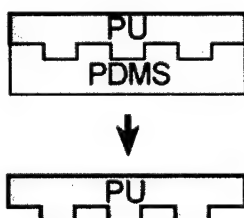
## Microtransfer molding



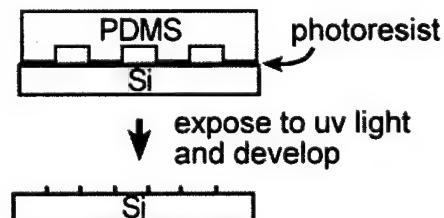
## Solvent-assisted Embossing



## Replica molding



## Near field lithography

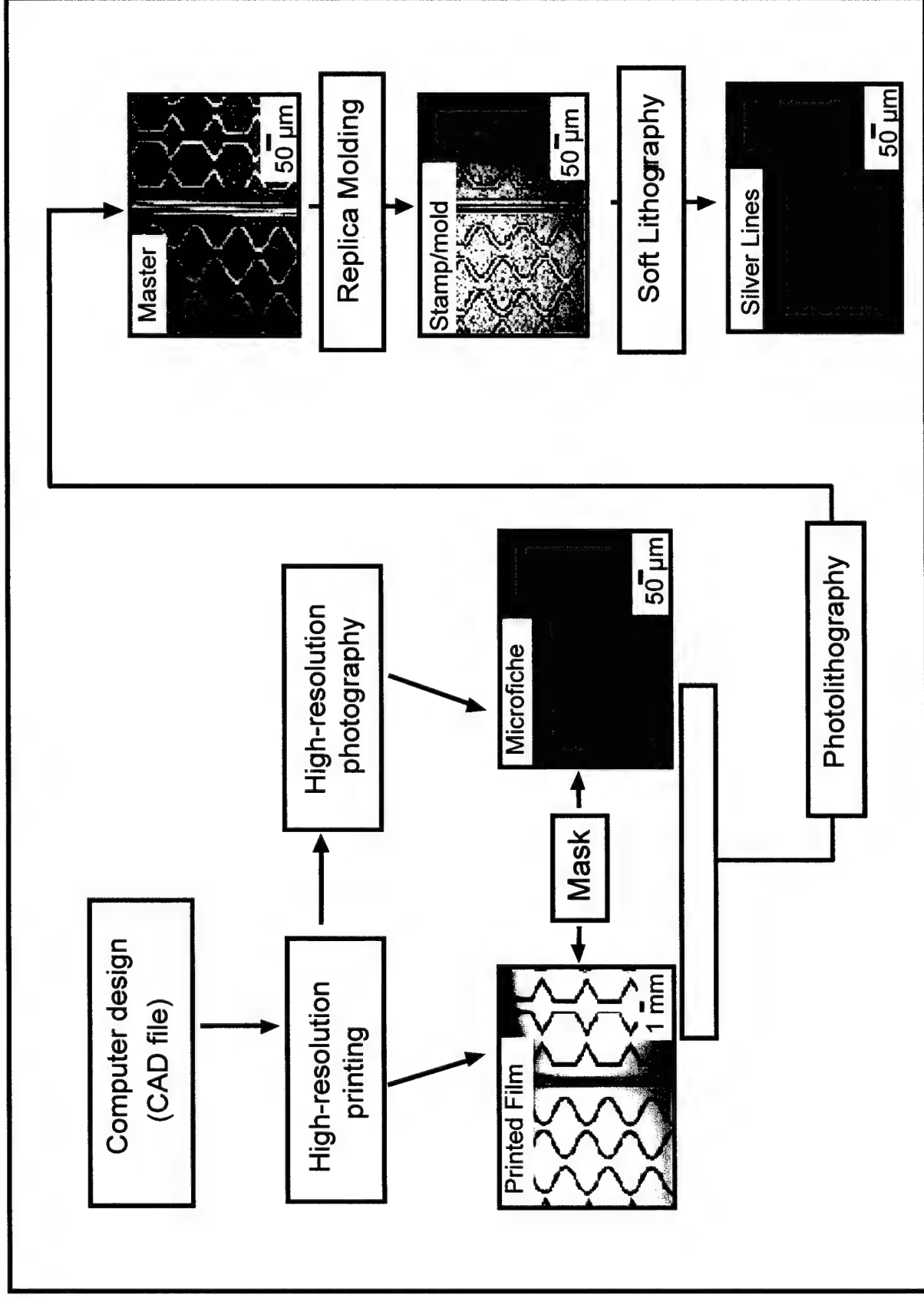


# Rapid Prototyping Using Soft Lithography

*Tao Deng, Dong Qin, and George M. Whitesides*  
*Department of Chemistry, Harvard University*

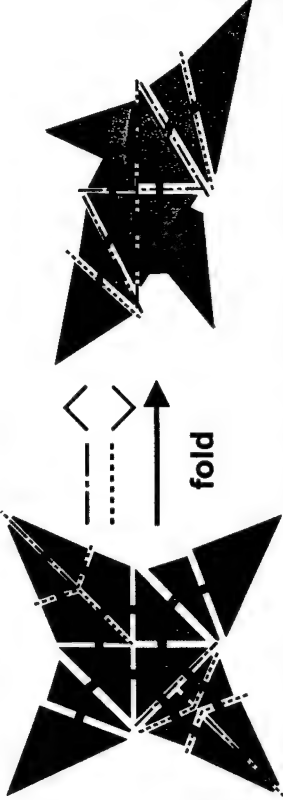
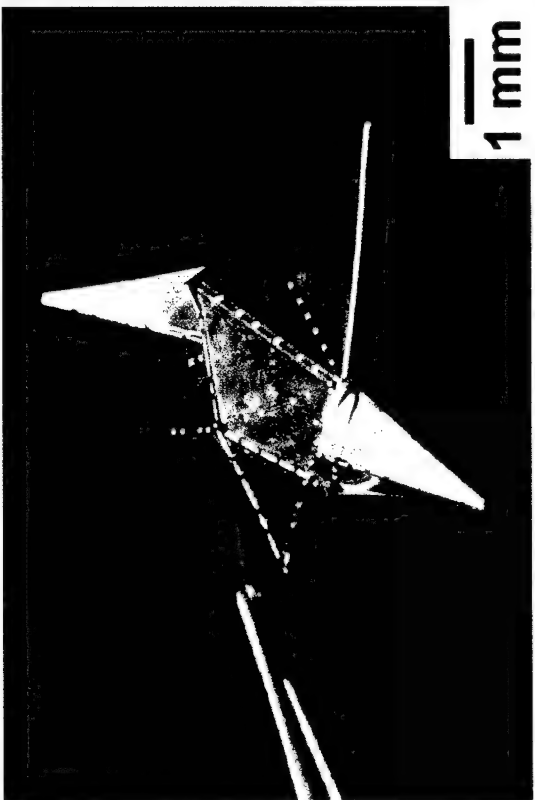
<p><b>Objective</b></p> <p>Development of new methods and materials for rapid prototyping of microstructures for chemistry, biology and materials laboratories</p>	<p><b>Technical Approaches</b></p> <pre>graph TD; idea([idea]) --&gt; CAD([CAD]); CAD -- "printing&lt;br/&gt;photographing" --&gt; mask([mask]); mask -- "PL" --&gt; master([master]); master -- "REM" --&gt; stamp([stamp&lt;br/&gt;or mold]); stamp -- "Soft&lt;br/&gt;lithography" --&gt; structure([structure]);</pre>	
<p><b>Accomplishments</b></p> <ul style="list-style-type: none"><li>• Rapid prototyping complex microstructures (&gt;20 μm) using printed film</li><li>• Rapid prototyping complex microstructures (&gt;10 μm) using microfiche</li></ul>		

## Process for Rapid Prototyping using Soft Lithography



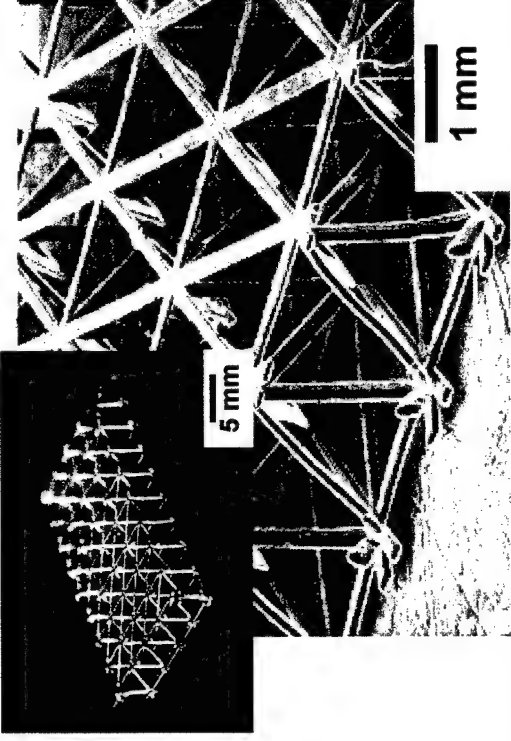
# Microelectrochemistry: Microorigami

Scott T. Brittain, Olivier Schueller, Hongkai Wu, Sue Whitesides (McGill),  
George M. Whitesides, Harvard University

<b>Objectives</b> <ul style="list-style-type: none"><li>• To fabricate complex, 3D structures in metals for potential use in MEMS, microrobotics, UAVs, microsatellites</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• <math>\mu</math>CP, wet etching, electroplating, manual folding</li></ul> 
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• 3D metallic structures fabricated from single layer, 2D patterning technique</li><li>• Topographical transformations</li><li>• sub-mm feature sizes</li></ul>	 1 mm

# Microelectrochemistry: Trussed Structures

*Scott T. Brittain, Olivier Schueller, Yuki Sugimura,  
Anthony G. Evans, George M. Whitesides, Harvard University*

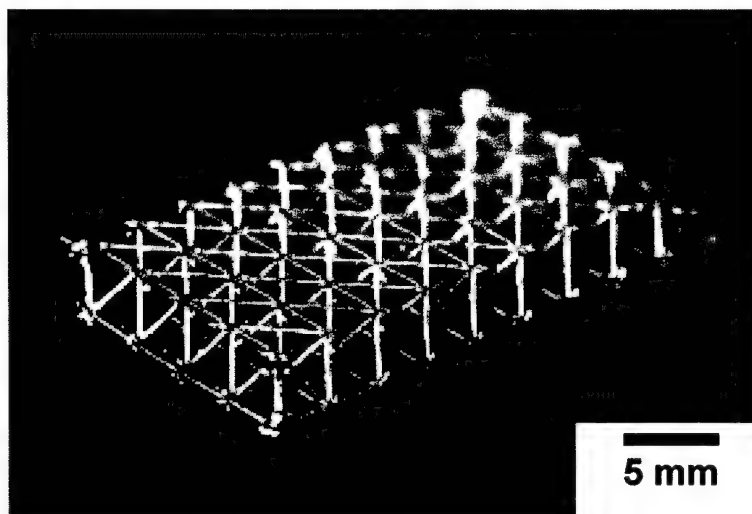
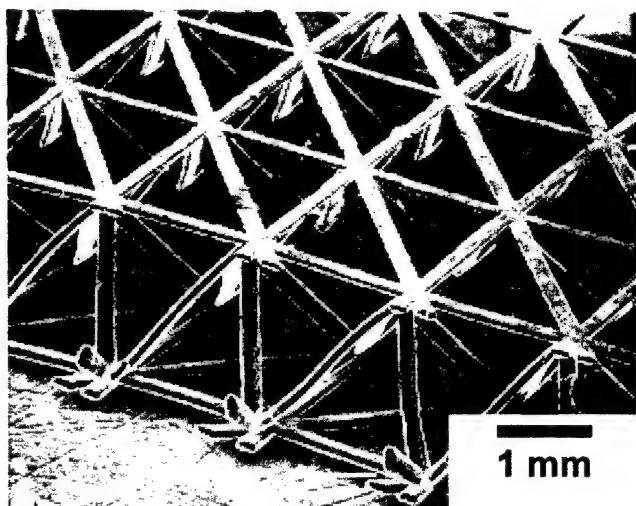
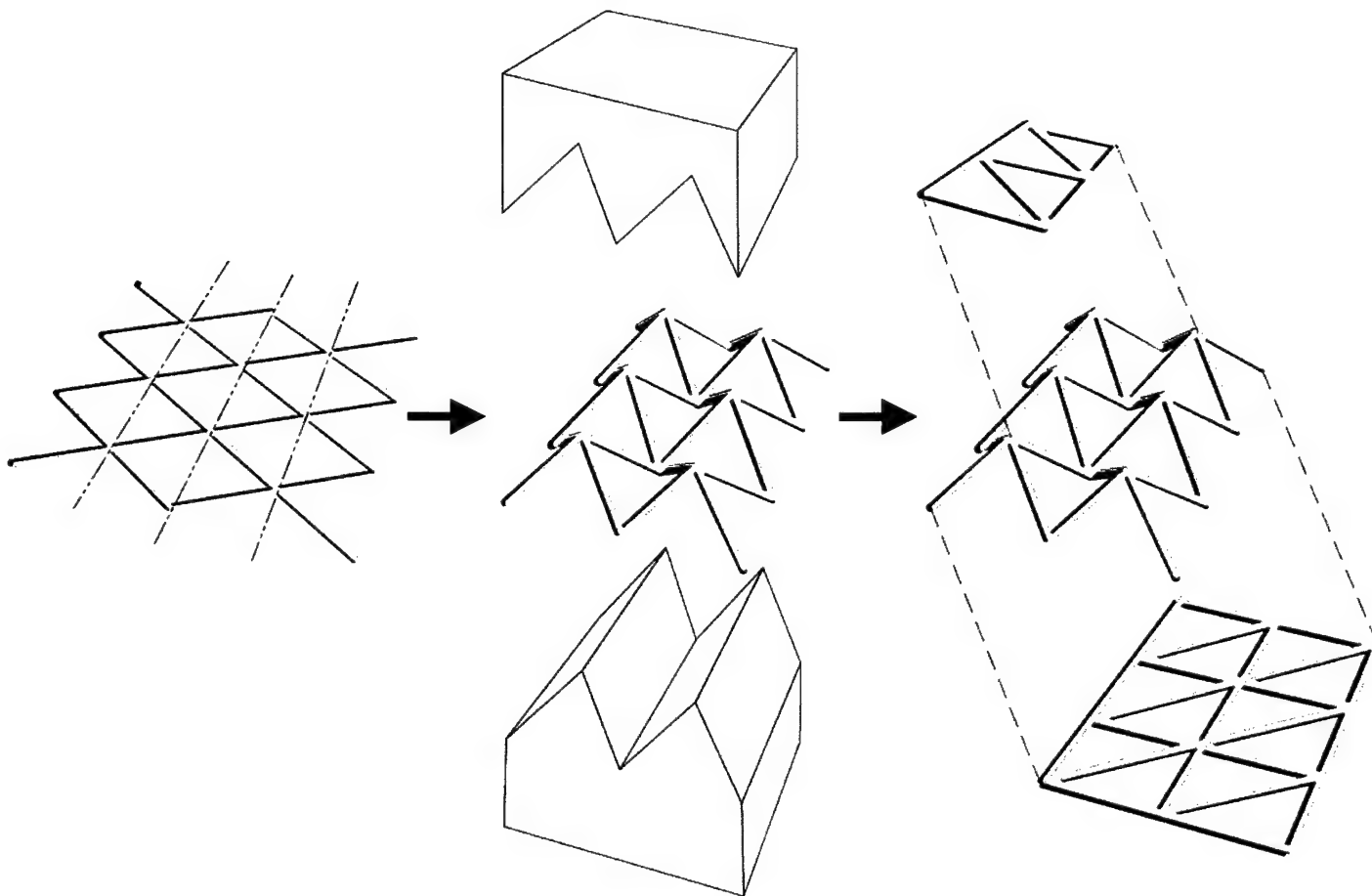
<b>Objectives</b> <ul style="list-style-type: none"><li>• To fabricate complex, 3D structural elements in metals for potential use in MEMS, microrobotics, UAVs, microsatellites</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• Microcontact Printing (<math>\mu</math>CP)</li><li>• Wet chemical etching</li><li>• Electroplating</li><li>• Manual assembly</li><li>• Electrochemical welding</li></ul>
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• Truly 3D metallic structures</li><li>• cm-scale objects with mm-scale structural repeats and <math>\sim 100\text{ }\mu\text{m}</math> feature sizes</li><li>• multilevel registration to <math>100\text{ }\mu\text{m}</math></li></ul>	

## Fabrication of Microtruss

Fabricate planar  
Ag grid using  $\mu$ CP  
and electroplating.

Fold 70 deg along  
axes using tweezers  
and brass die.

1. Assemble by Hand.  
2. Affix corners with Ag paint.  
3. Electroplate Ni.





# Topographically Directed Photolithography: Photoresist as its Own Optical Element

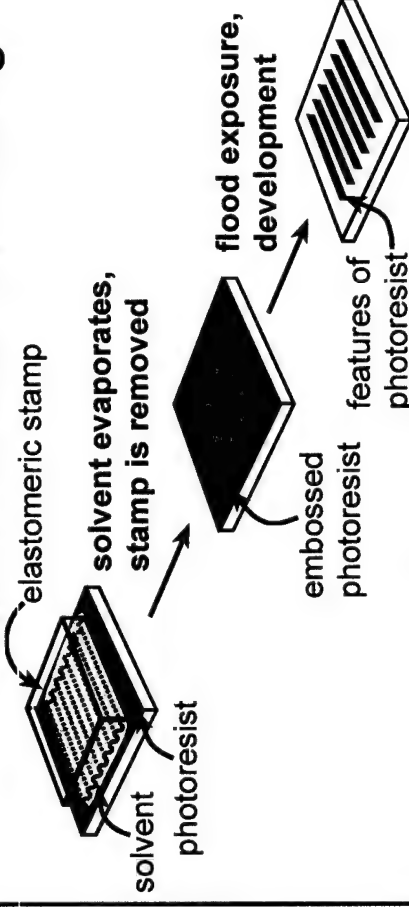
*Kateri E. Paul, Tricia L. Breen, Joanna Aizenberg and George M. Whitesides  
Department of Chemistry and Chemical Biology, Harvard University*

## Objective:

Generate < 100-nm features over a large area using an unconventional photolithographic technique: maskless lithography.

## Technical Approach:

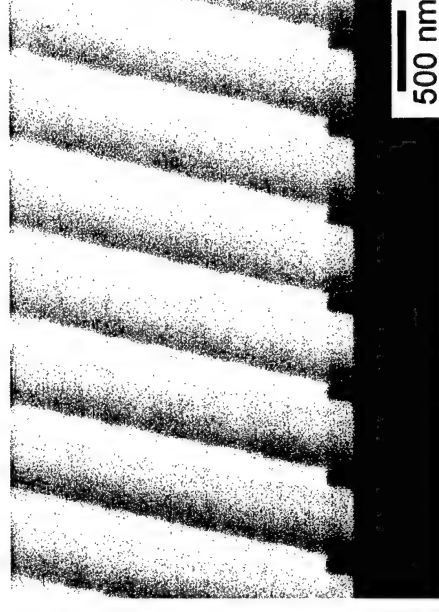
### Solvent Assisted Embossing



## Accomplishments:

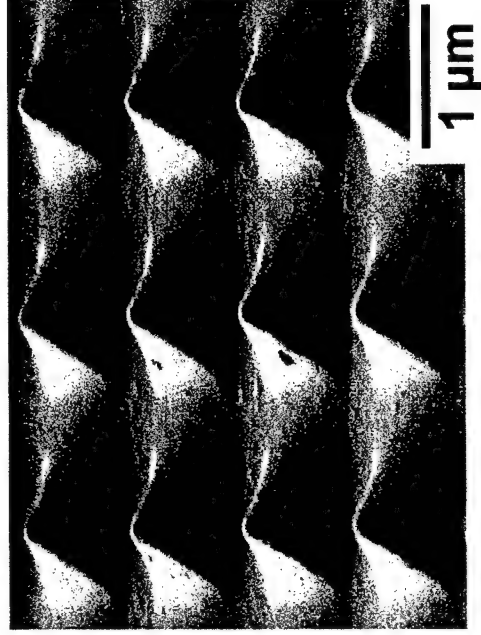
- Features as small as ~ 70 nm, with a period of ~400 nm, generated in photoresist on silicon
- Reactive ion etching (RIE) and lift-off transfer features to the substrate
- Technique can be combined with an amplitude mask to generate more complex structures
- Areas of ~8 cm<sup>2</sup> patterned

## ~70 lines produced by a sinusoidal grating

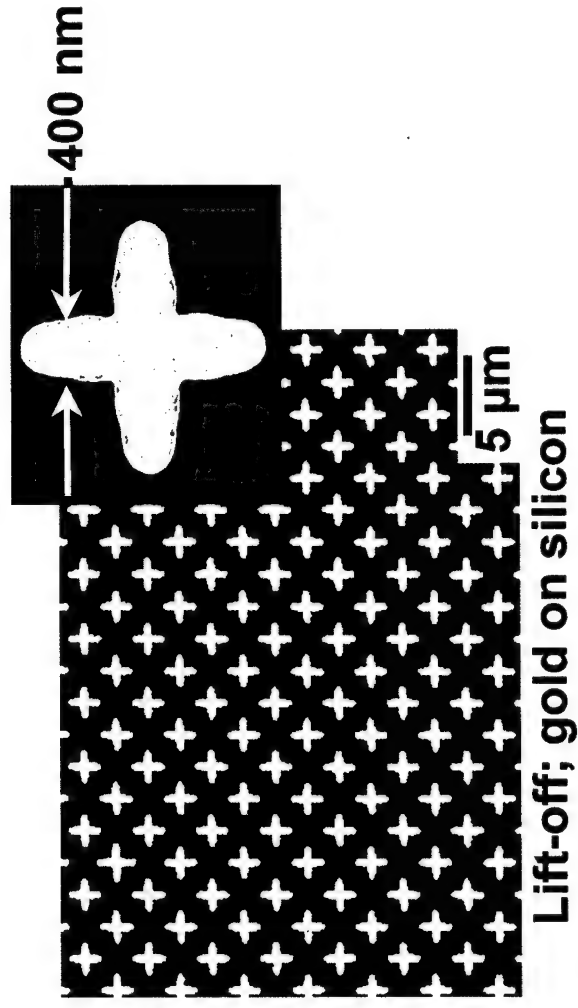
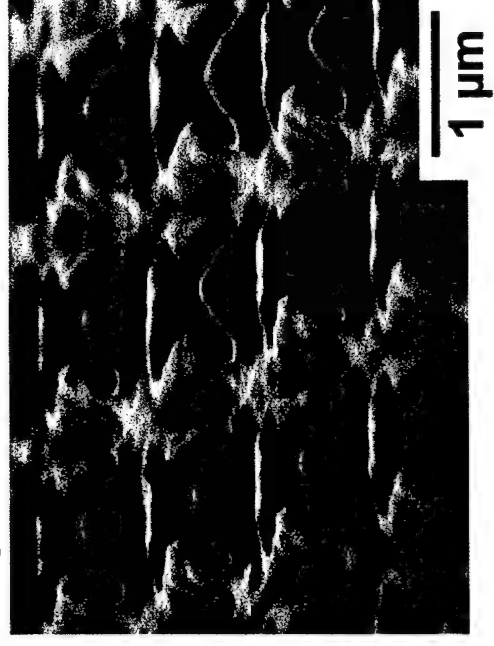


# Topographically Directed Photolithography: generation of a dipole array

Embossed photoresist




Exposed photoresist

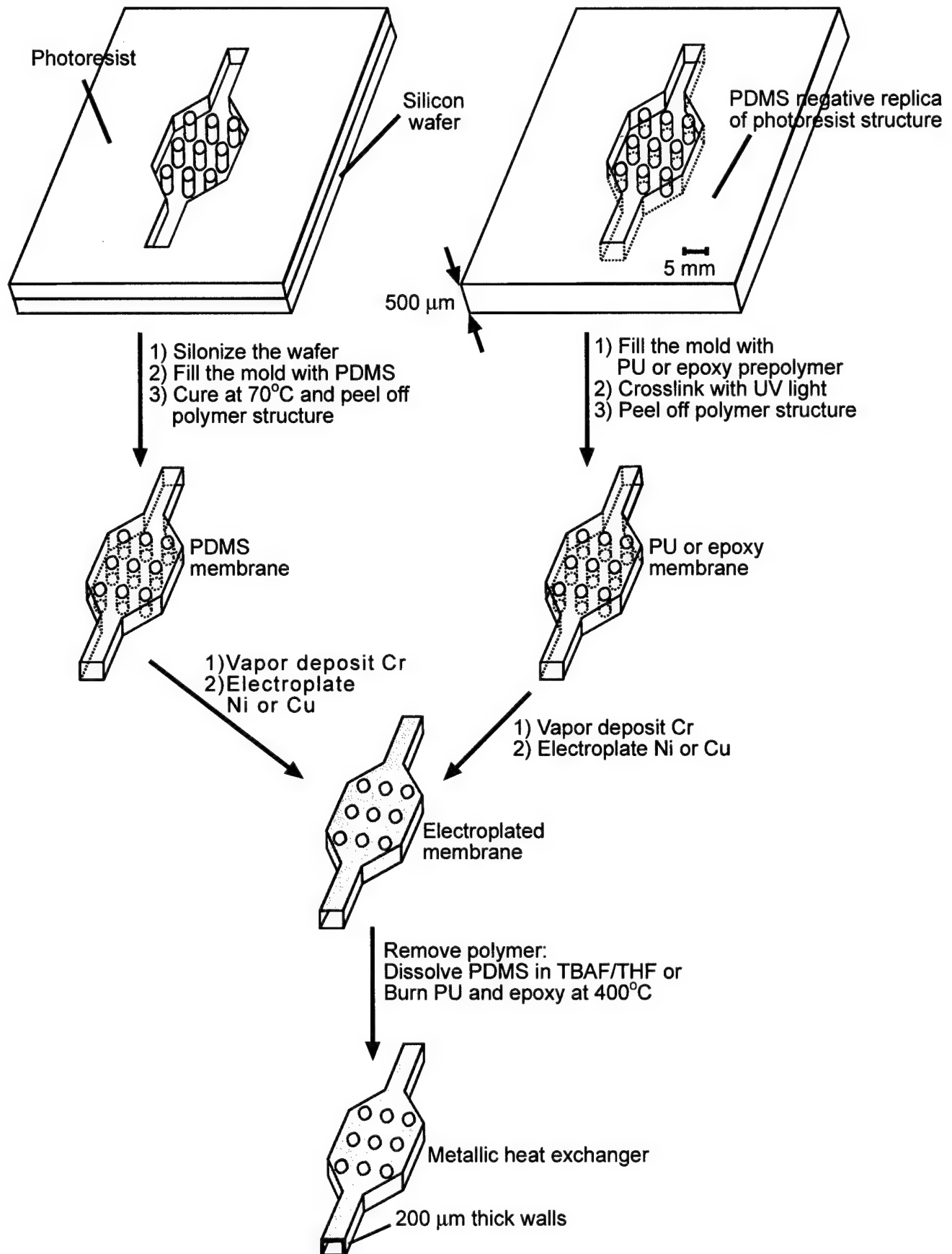


# Fabrication of Metallic Heat Exchangers Using Sacrificial Polymer Mandrills

*Francisco Arias, Scott Oliver, Bing Xu, and George M. Whitesides\**  
*Department of Chemistry, Harvard University*

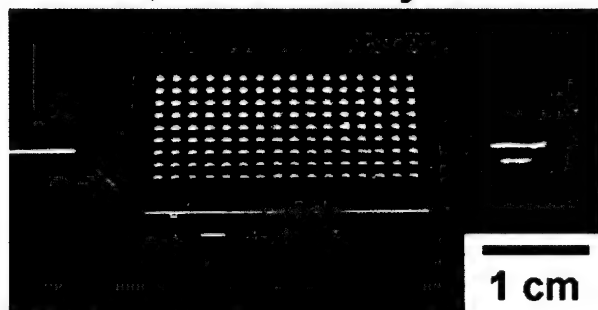
<p><b>Objectives:</b> New processes, use sacrificial polymer frameworks to construct three-dimensional metallic structures.</p> <p><b>Applications:</b> Cooling systems for electronic components and diffraction gratings.</p>	<p><b>Technical Approach:</b></p> <ul style="list-style-type: none"> <li>• Rapid prototyping</li> <li>• Microtransfer molding</li> <li>• Vapor deposition</li> <li>• Electroplating</li> </ul>
<p><b>Accomplishments:</b></p> <ul style="list-style-type: none"> <li>• Fabricated nickel thermal modules with 200-500 <math>\mu\text{m}</math> wide channels.</li> <li>• We are able to prepare heat exchangers with various features: 400-200 <math>\mu\text{m}</math> unfilled cylinders, 500 <math>\mu\text{m}</math> stripes, or 150 <math>\mu\text{m}</math> posts.</li> </ul>	<p><b>Heat Exchanger Design</b></p> 

# Fabrication of Heat Exchangers

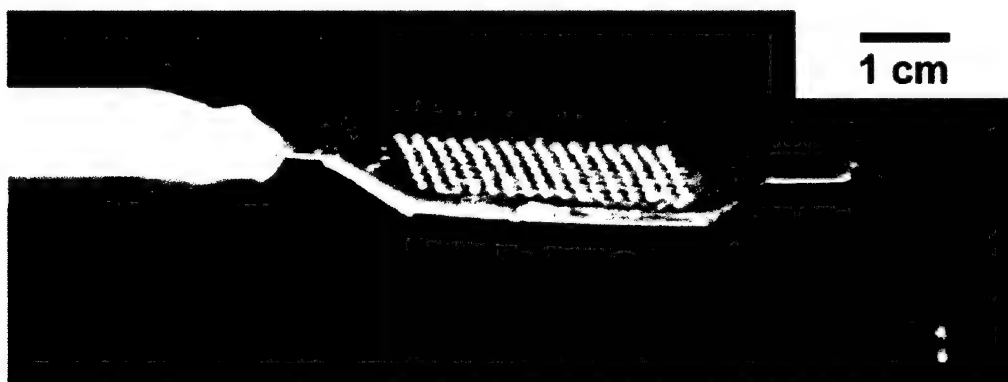
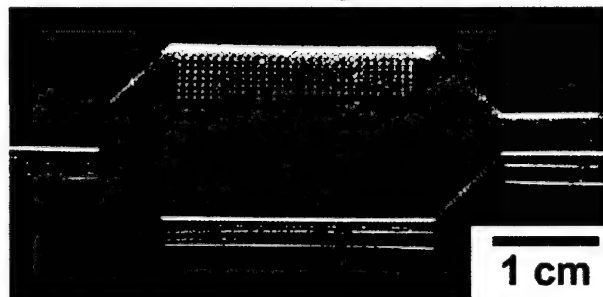


# Characterization of Heat Exchangers

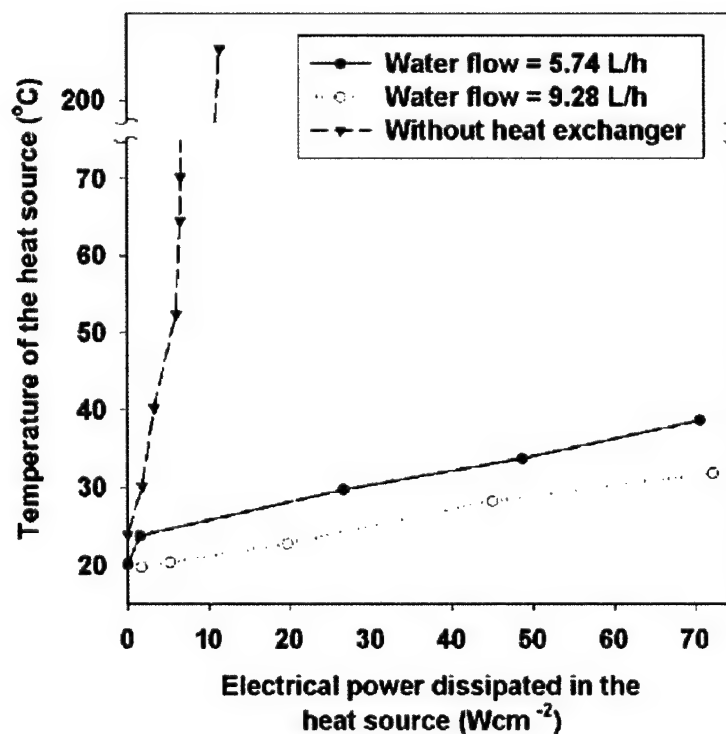
400  $\mu\text{m}$  unfilled cylinders



150  $\mu\text{m}$  posts




Performance of nickel specimen with  
400  $\mu\text{m}$  unfilled cylinders

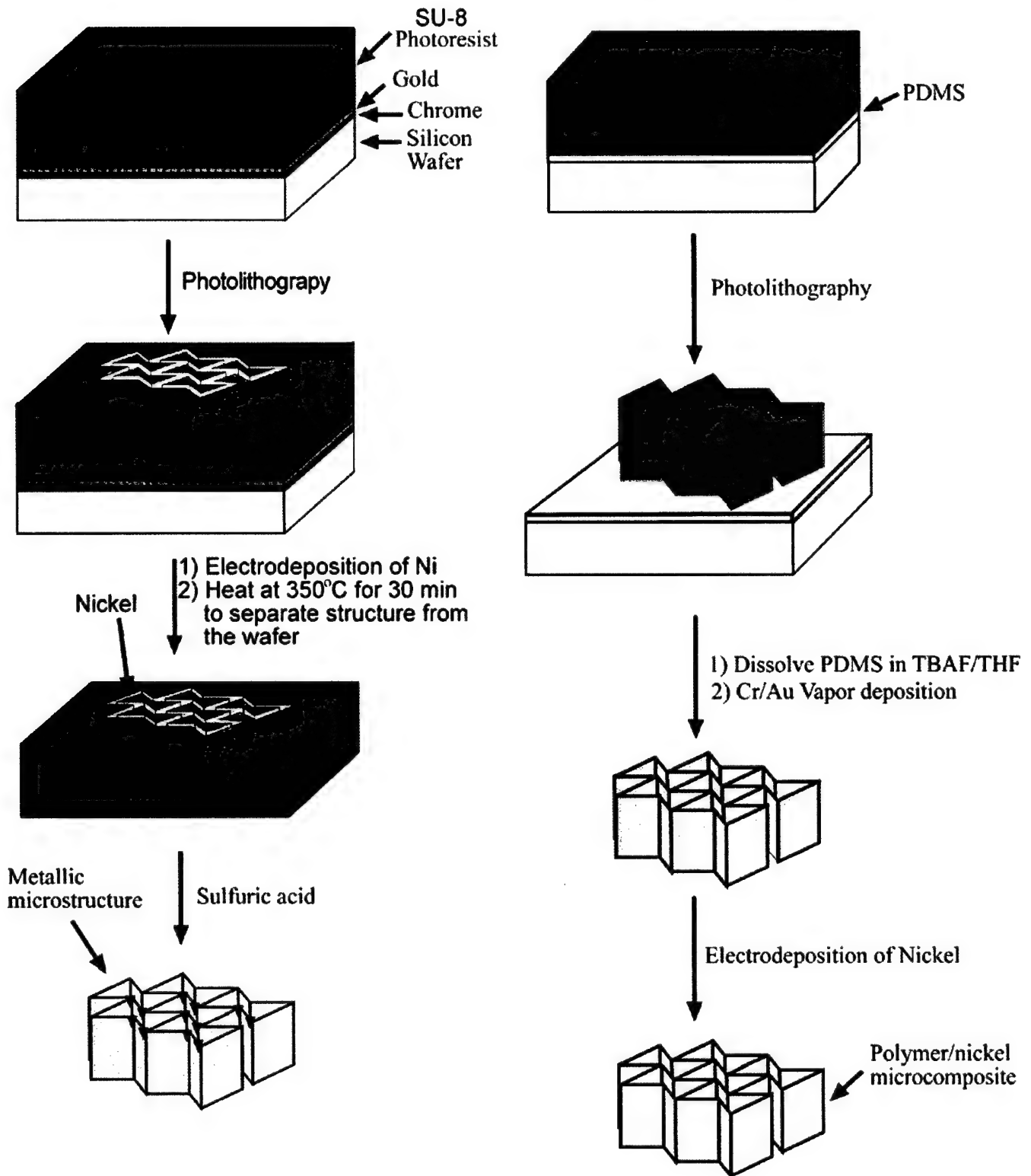


# Microscale Sandwich Panels

*Francisco Arias, Bing Xu, George M. Whitesides\*, Yuki Sugimura, Anthony Evans\**  
*Department of Chemistry, Harvard University*

<p><b>Objectives:</b> Fabrication of materials with high strength-to-weight ratio and low production cost.</p> <p><b>Applications:</b> Hard disk drive arms, small air vehicles, military equipment, hydrophones, and structural biomaterials.</p>	<p><b>Technical Approach:</b></p> <ul style="list-style-type: none"><li>• Rapid prototyping</li><li>• Microtransfer molding</li><li>• Microembossing</li><li>• Electroplating</li><li>• Pb/Sn Soldering</li></ul>
<p><b>Accomplishments:</b></p> <ul style="list-style-type: none"><li>• Fabricated metallic and polymeric microgrids with high-aspect-ratio : honeycombs, negative Poisson's ratio, and quasiperiodic patterns.</li><li>• Prepared microscale sandwich panels and measured their bending moduli.</li></ul>	<p><b>Metallic Honeycomb Panel</b></p> 

# Fabrication of Microgrids



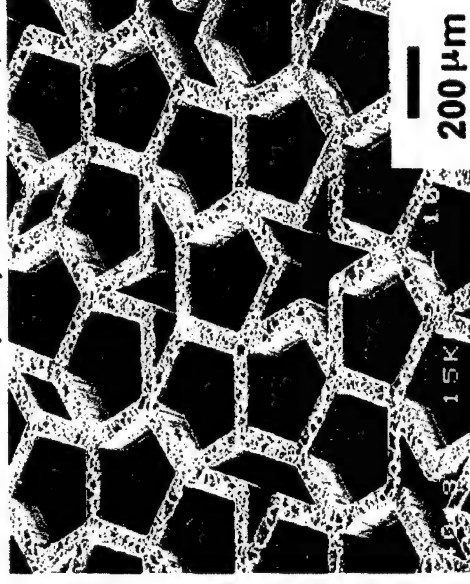
## Metallic Microgrids

Honeycombs

Diam = 150  $\mu\text{m}$ ; WW = 15  $\mu\text{m}$



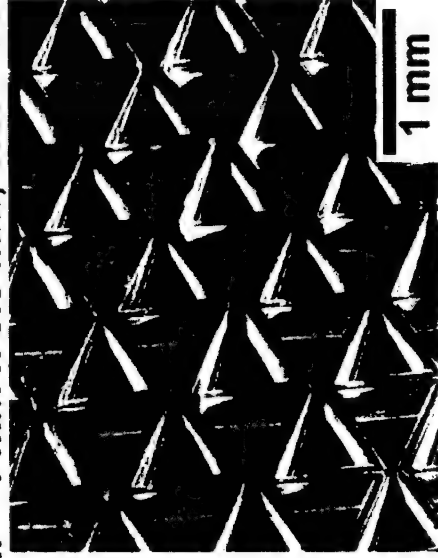
Kemper's pentaling  
Diam = 400  $\mu\text{m}$ ; WW = 75  $\mu\text{m}$



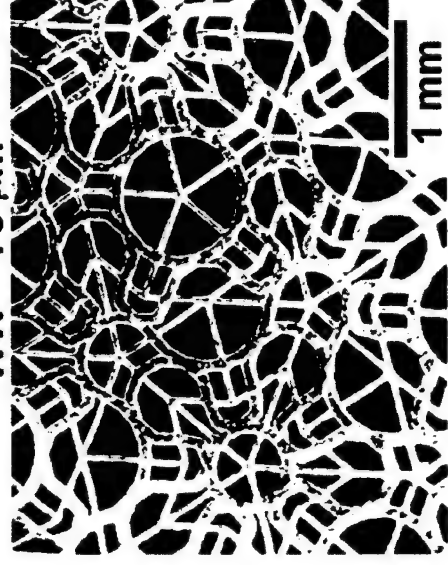
## Polymer/Metal Microgrids

NPR structure

Cell = 1 mm x 0.5 mm; WW = 75  $\mu\text{m}$



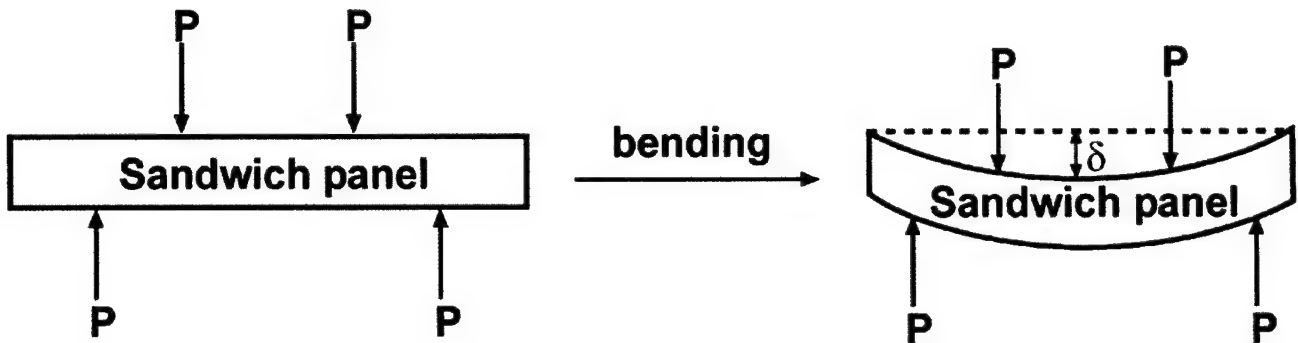
A Penrose's structure  
WW = 75  $\mu\text{m}$





# Bending Tests of Sandwich Panels

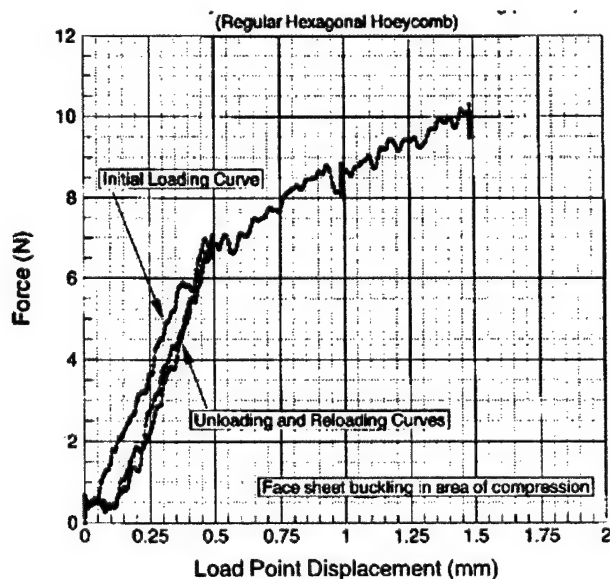
Four-point bending test:



$\delta$  = load point displacement

$$EI = 6.67 \times 10^{-7} P/\delta$$

Force vs. load displacement plot for a nickel honeycomb panel:

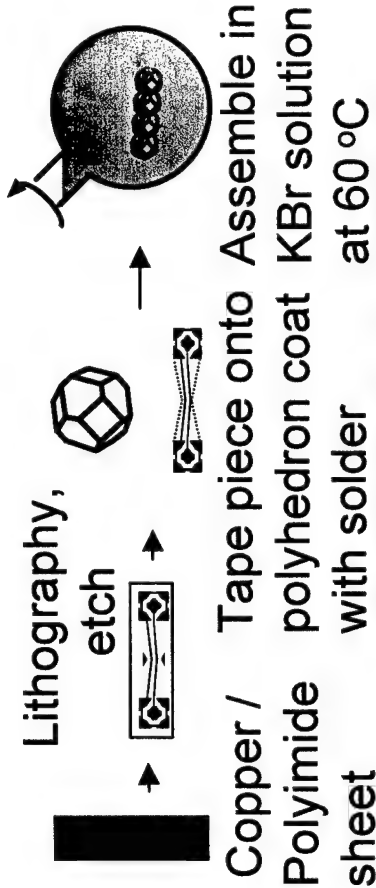
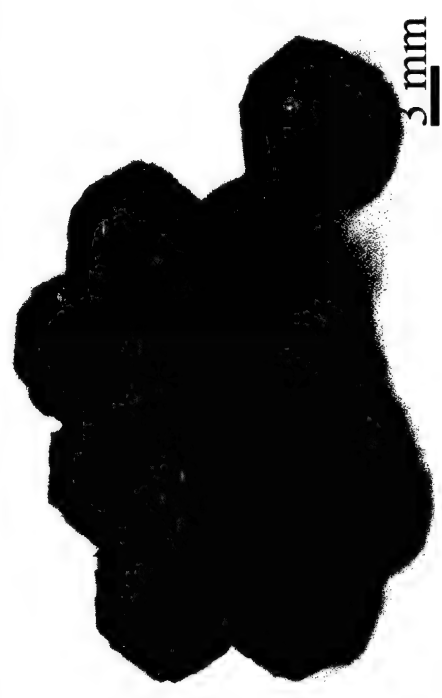


Bending Moduli:

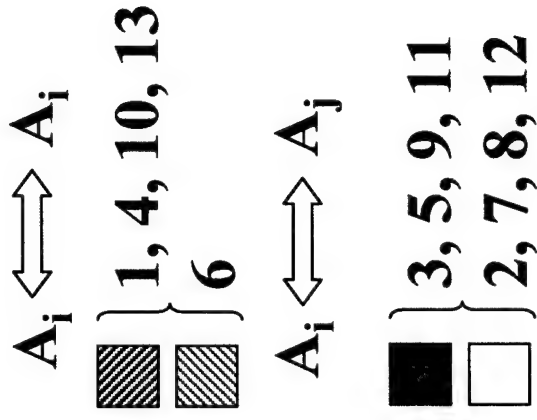
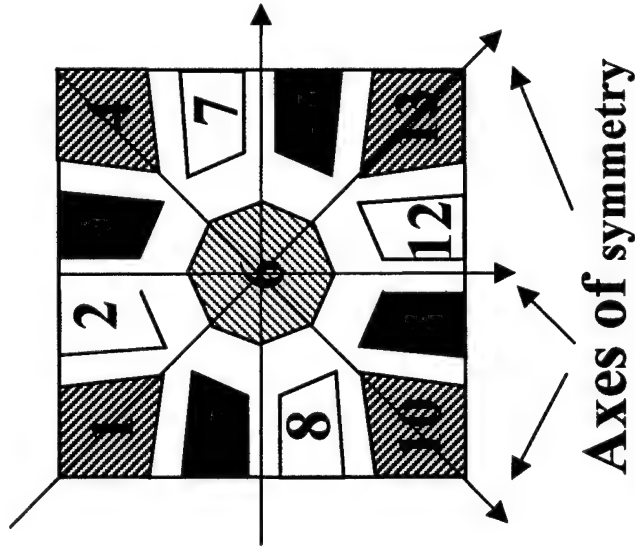
Exp. 136 GPa  
Theor. 132 GPa

# Forming Electrical Networks in Three Dimensions by Self-Assembly

*D. H. Gracias, J. Tien, T. L. Breen, C. Hsu and G. M. Whitesides  
Department of Chemistry and Chemical Biology, Harvard University*

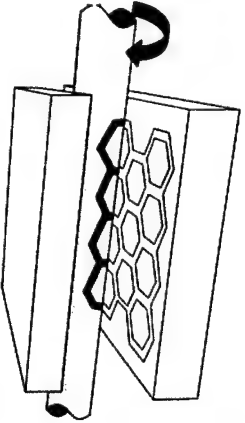
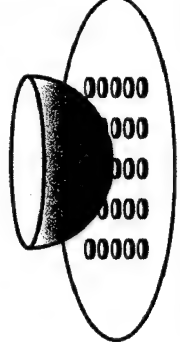
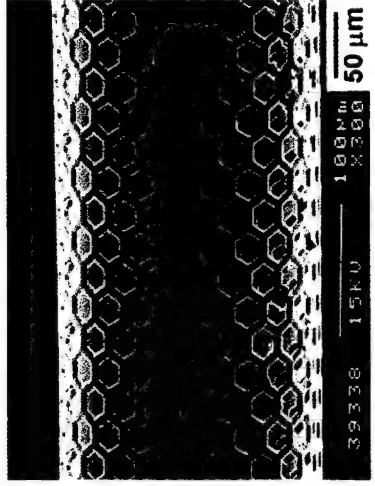
<p><b>Objectives:</b></p> <ul style="list-style-type: none"> <li>• Demonstrate self-assembly with pin-on-pin electrical contacts.</li> <li>• Self-assemble electrical networks in three dimensions with local and global connectivity.</li> </ul>	<p><b>Technical Approach:</b></p>  <p>Copper / Polyimide sheet      Lithography, etch      Tape piece onto Assemble in KBr solution at 60 °C</p>
<p><b>Accomplishments:</b></p> <ul style="list-style-type: none"> <li>• Self-assembled 2x2x3 polyhedra with local and global networks.</li> <li>• Self-assembled wedge shaped polyhedra to form a solenoid.</li> </ul>	 <p>3 mm</p>

# Pin-On-Pin Connections and Connectivity



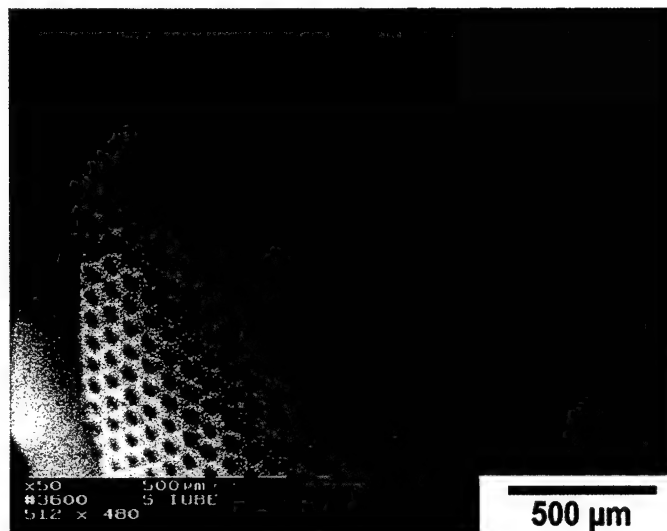
# Printing on Curved Surfaces

R. Jackman, S. Brittain, H. Wu, G.M. Whitesides,  
Department of Chemistry, Harvard University

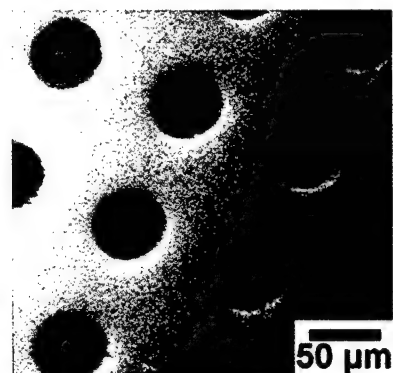
<b>Objective</b> <ul style="list-style-type: none"><li>• To Pattern curved surfaces</li><li>• To fabricate microstructures using the curved surfaces as sacrificial layer</li></ul>	<b>Technical Approach</b>  <p>press</p>  <p>PDMS membrane stamp</p>
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• Features <math>\geq 3 \mu\text{m}</math> were printed on cylindrical surfaces (curvature <math>\geq 100 \mu\text{m}</math>)</li><li>• Features <math>\geq 1 \mu\text{m}</math> were printed on spherical surfaces (curvature <math>\geq 2 \text{ mm}</math>, and <math>\geq 60</math> degrees of the surface area)</li></ul>	

# Print on Curved Surfaces

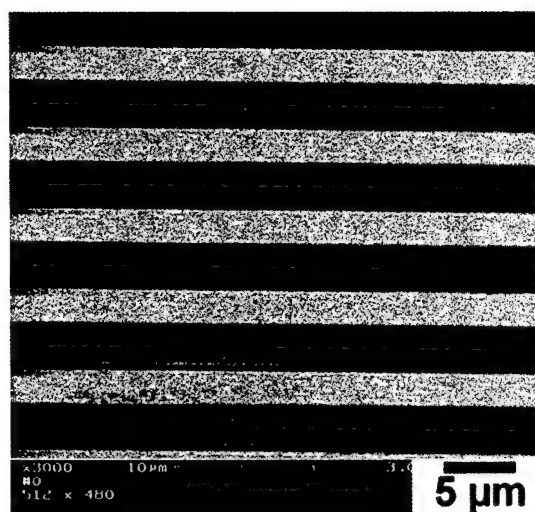
spherical surface



apex

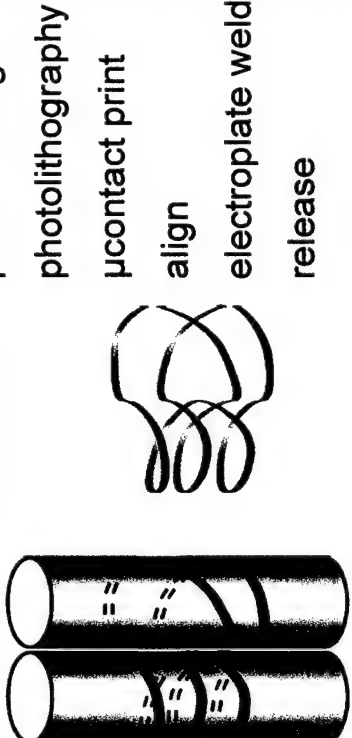
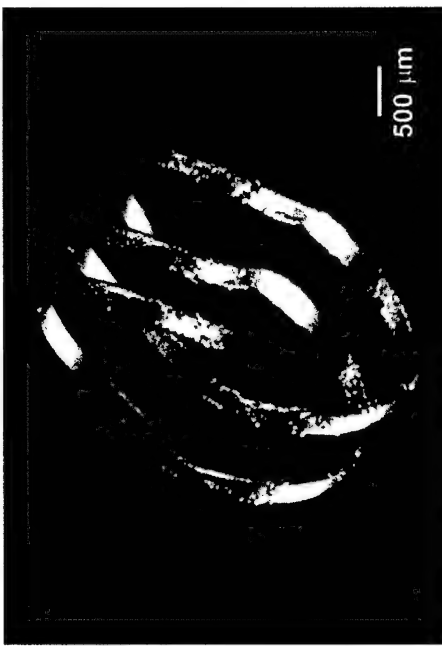


edge

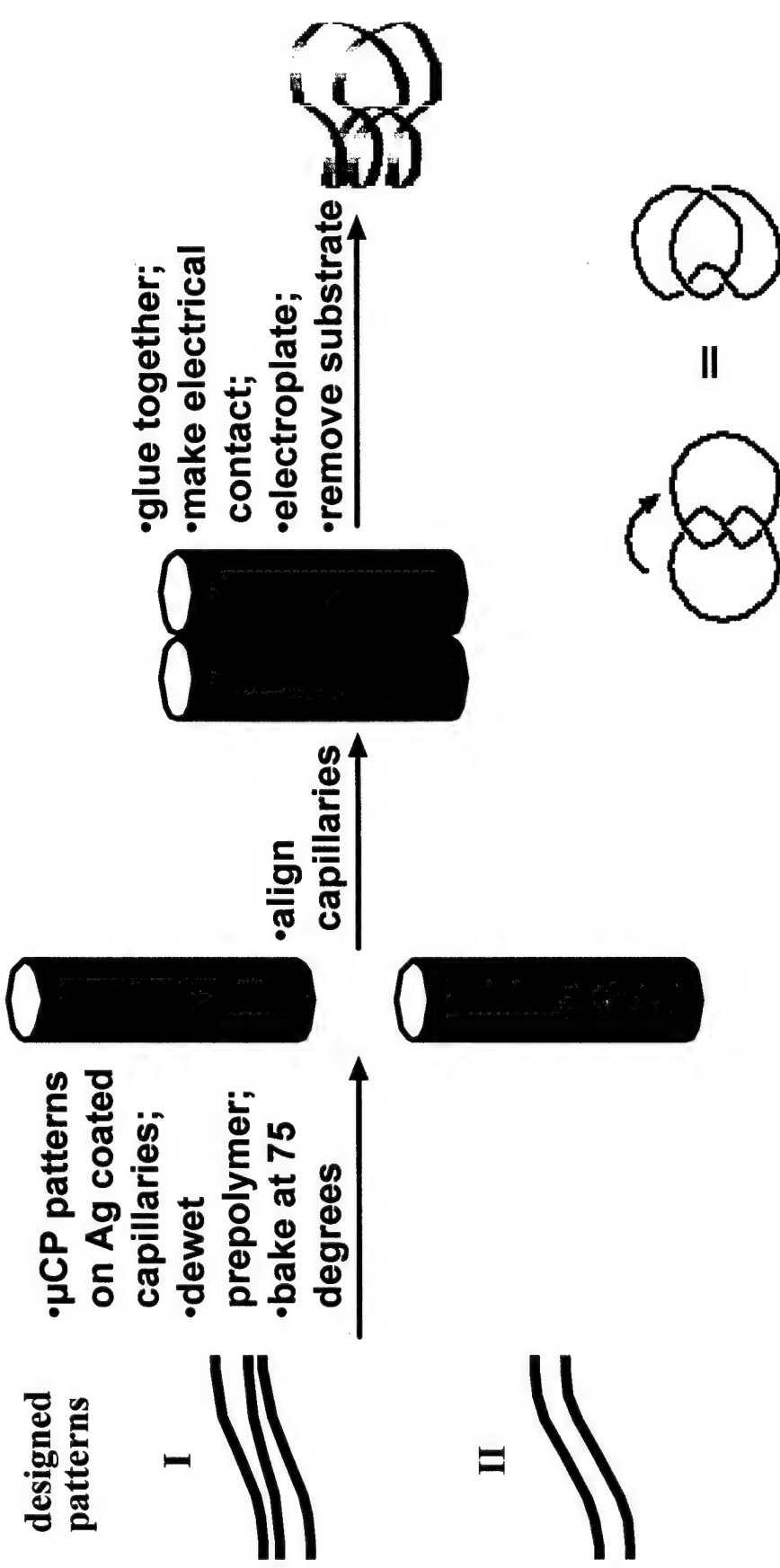


# Complex Geometry

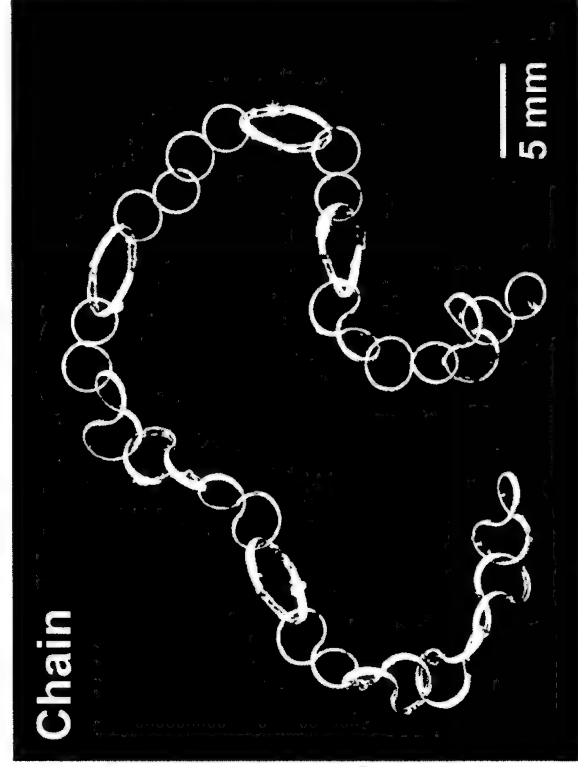
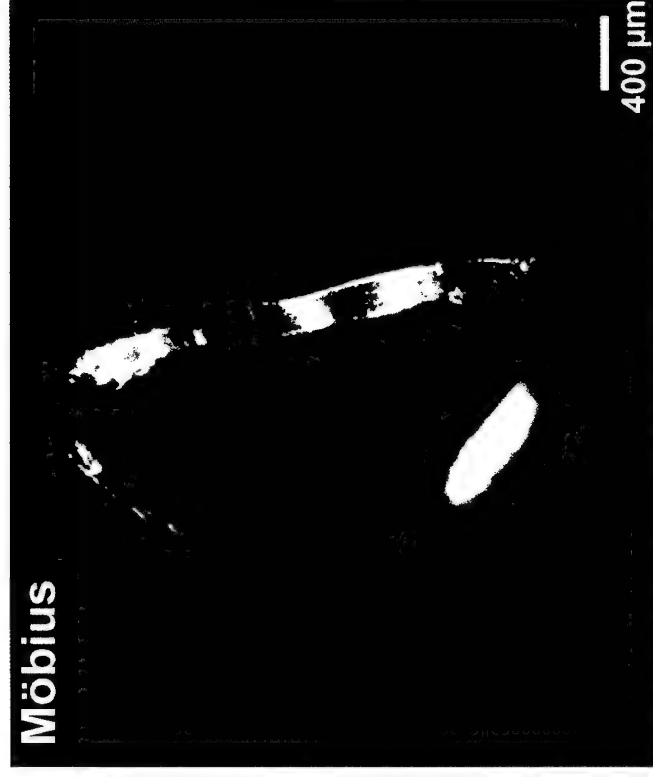
Hongkai Wu, Scott Brittain, Bartosz Grzybowski, Prof. Sue Whitesides, Prof. G.M. Whitesides  
Department of Chemistry, Harvard University

<p><b>Objectives</b></p> <ul style="list-style-type: none"> <li>To fabricate topologically complex three-dimensional objects</li> </ul>	<p><b>Technical Approach</b></p>  <p>pattern design photolithography <math>\mu</math>contact print align electroplate weld release</p>
<p><b>Accomplishment</b></p> <ul style="list-style-type: none"> <li>Increased topological complexity             <ul style="list-style-type: none"> <li>— planar design <math>\rightarrow</math> multiple crossings</li> </ul> </li> <li>Complex 3D structures             <ul style="list-style-type: none"> <li>— knots</li> <li>— chains</li> <li>— Möbius strip</li> </ul> </li> </ul>	 <p>500 <math>\mu</math>m</p>

# Fabrication of Complex Geometry



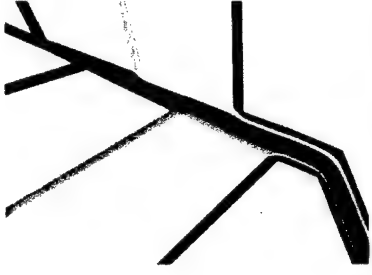
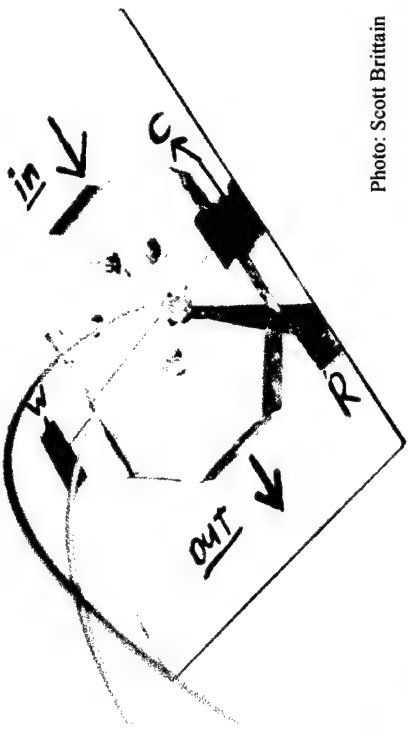
# Complex Geometry





# Fabrication using Laminar Flow

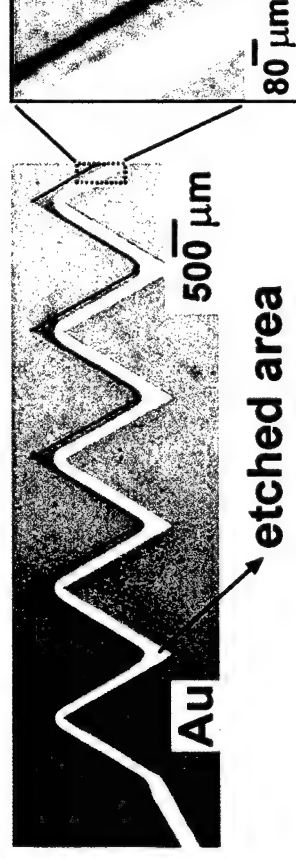
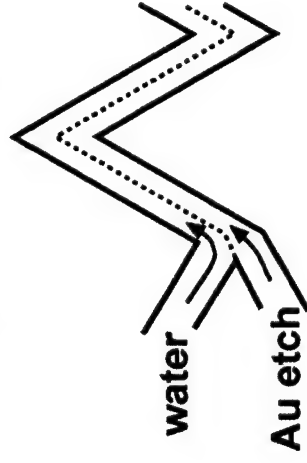
Paul Kenis, Rustem Ismagilov, and George M. Whitesides  
Department of Chemistry and Chemical Biology, Harvard University

<b>Objective</b>  Microfabrication inside capillaries (PDMS, glass, composite)	<b>Technical Approach</b>  Apply different chemistries from - separate flows - at the interface of flows using <i>multiphase laminar flows</i>   Photo: F. Frankel
<b>Accomplishments</b>  - arrays of crystals - ridges of polymer - trenches in SiO <sub>2</sub> - chemiluminescence - electrode systems	<b>Three-electrode system:</b>   Photo: Scott Brittain

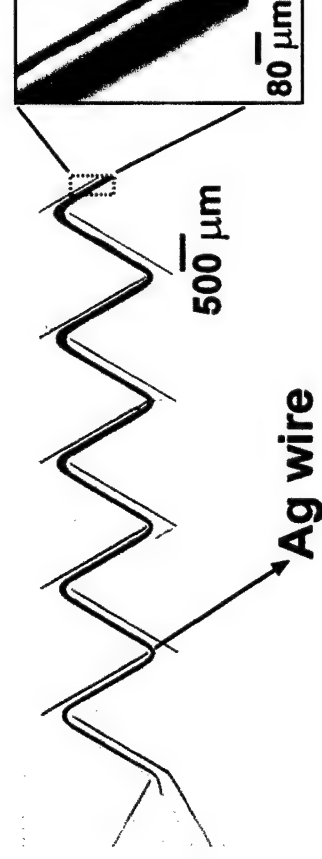
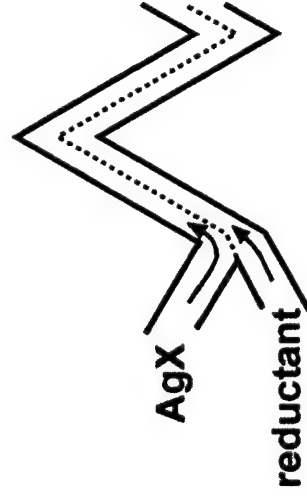
# Fabrication using Multiphase Laminar Flow

*Apply different chemistries from different phases*

From separate flows

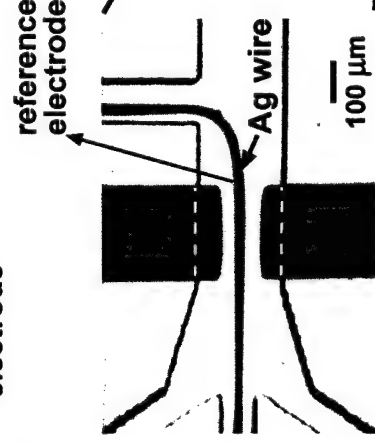
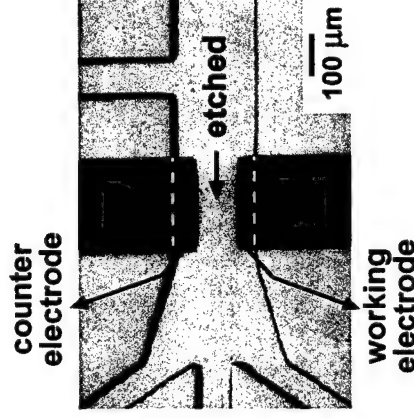
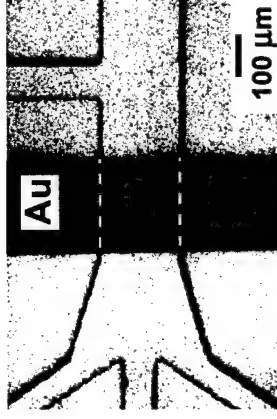
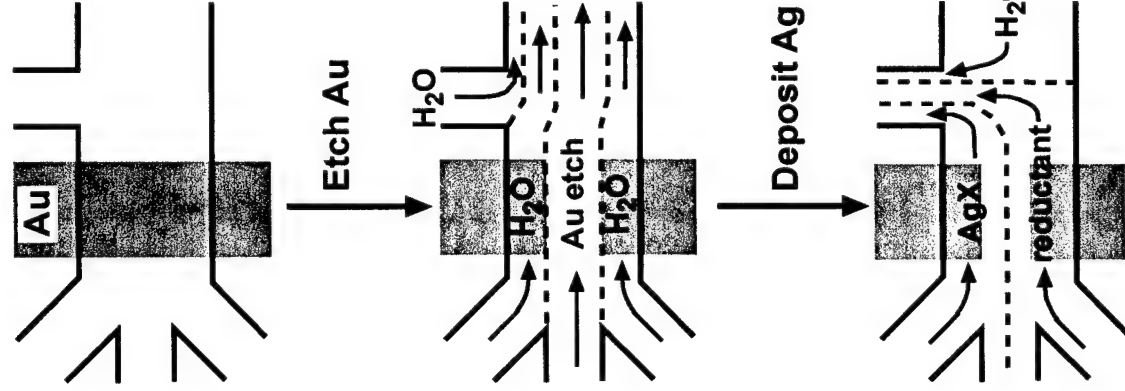


At the interface of flows

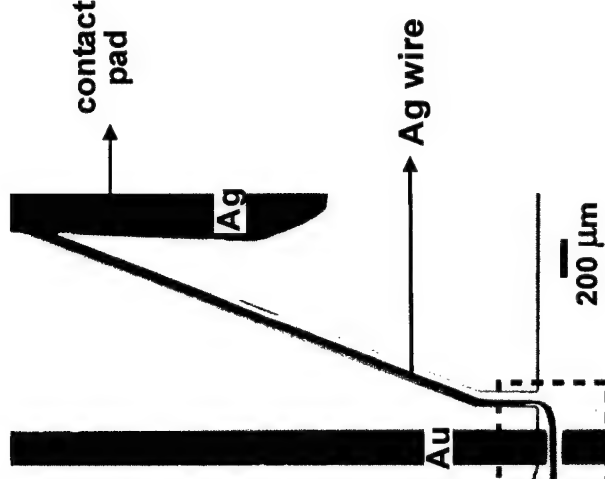
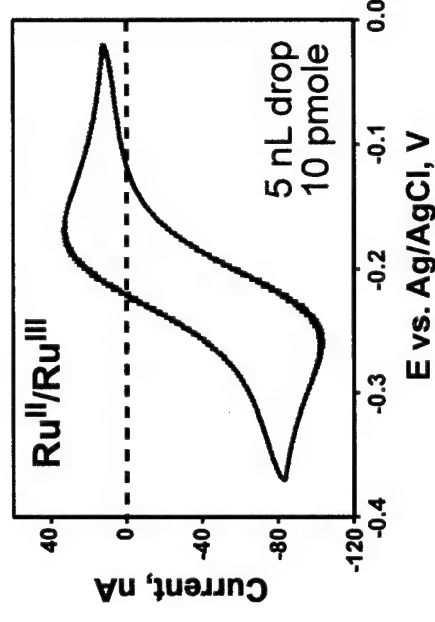


# In-Channel Three-Electrode System

## Fabrication



## Cyclic voltammetry

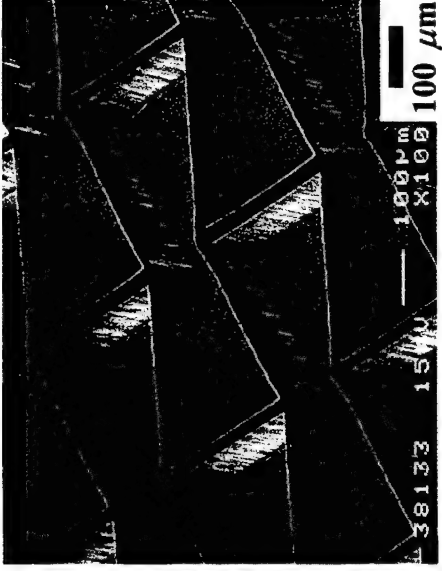


# Ceramics: SiC

*Scott T. Brittain, Hong Yang,*

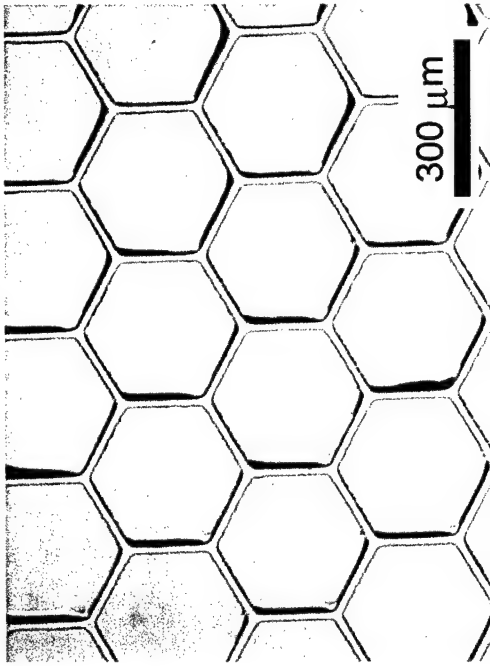
*George M. Whitesides, Harvard University*

*Martin Erhardt, Ralph Nuzzo, University of Illinois at UC*

<b>Objectives</b> <ul style="list-style-type: none"><li>• To coat patterned glassy carbon microstructures with a SiC shell.</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• <math>\mu</math>TM of precursor to carbon</li><li>• pyrolytic conversion to glassy carbon</li><li>• vapor deposition of Si</li><li>• pyrolytic conversion to SiC</li></ul>
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• Coating of glassy carbon microstructure with 4 <math>\mu</math>m of Si.</li></ul>	 <p>Glassy carbon microstructure before Si deposition.</p>

# New Ceramics for the Fabrication of Small Structures

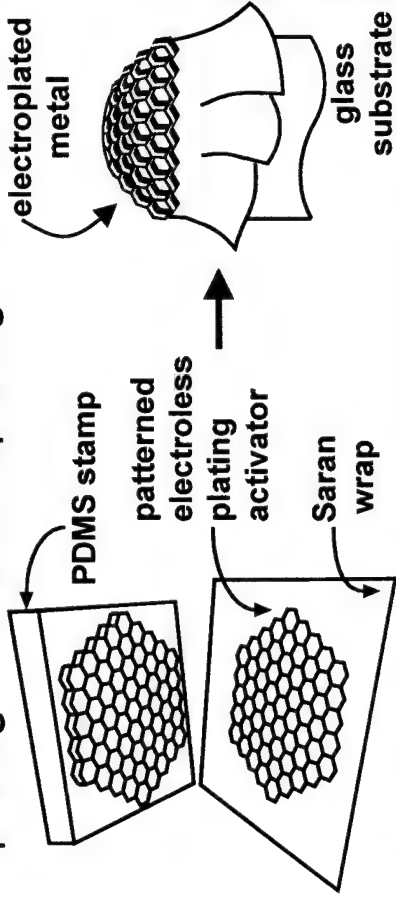
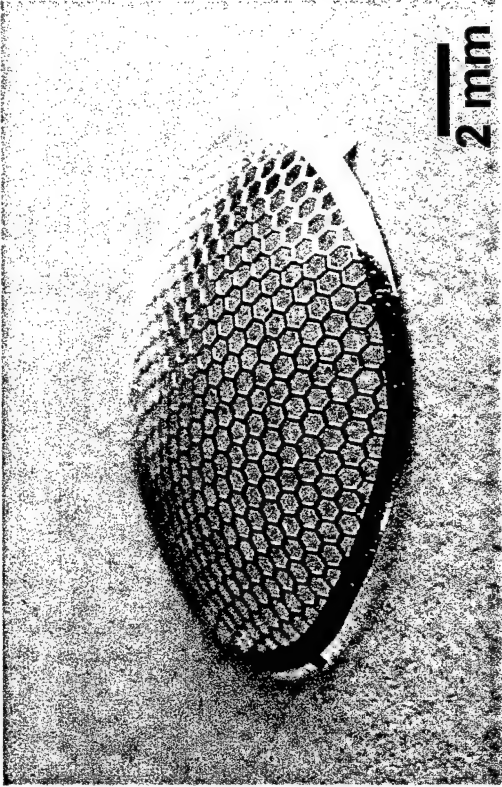
*Hong Yang, Scott T. Brittain, Pascal Deschatelets, Robert G. Chapman, and George M. Whitesides  
Department of Chemistry & Chemical Biology, Harvard University*

<b>Objectives</b> <ul style="list-style-type: none"><li>• To fabricate small functional structures of high performance ceramics for potential use in MEMS, microengines</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• Single source ceramic precursors</li><li>• Micromolding</li><li>• High temperature pyrolysis</li></ul>
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• Si/B/C/N precursors</li><li>• Test patterns of such Si/B/C/N ceramic at ~100 <math>\mu\text{m}</math> level</li></ul>	

# Microelectrochemistry: Saran Wrap Electroplating

*Wilhelm Huck, Scott T. Brittain, Hongkai Wu,*

*George M. Whitesides, Harvard University*

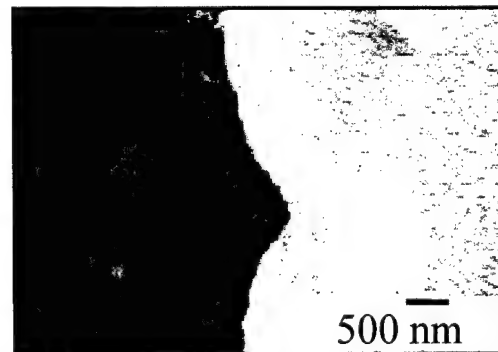
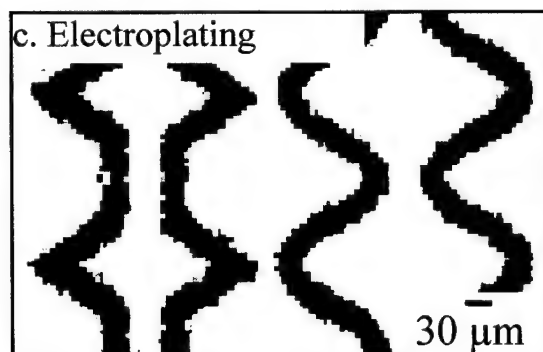
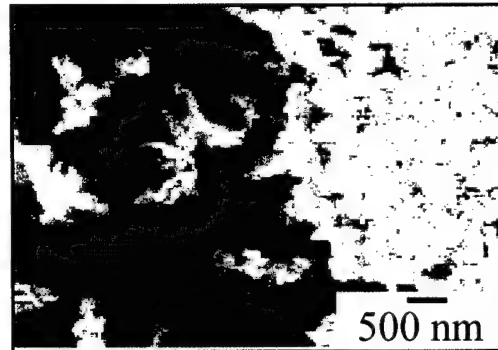
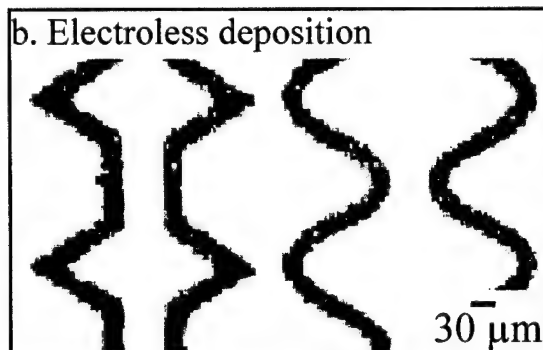
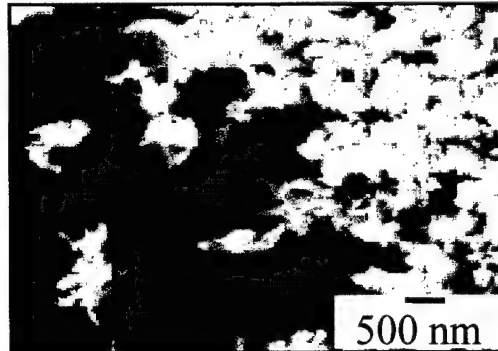
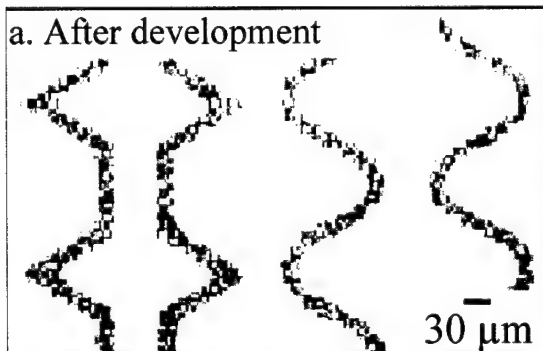
<b>Objective</b> <ul style="list-style-type: none"><li>• To pattern nonplanar, non-cylindrical substrates with feature sizes ranging from 1 to 100 <math>\mu\text{m}</math>.</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• <math>\mu\text{CP}</math>, flexible substrates, electroless plating and electroplating</li></ul> 
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• Patterned 1 cm radius of curvature over a <math>60^\circ</math> arc</li><li>• Freestanding structures</li><li>• <math>\sim 100 \mu\text{m}</math> feature sizes</li></ul>	

# Rapid Prototyping Using Silver Halide-based Film

Tao Deng, F. Arias, R. F. Ismagilov, P. J. A. Kenis,  
and George M. Whitesides  
Department of Chemistry, Harvard University

<b>Objective</b>  Development of new methods for rapid prototyping of metallic microstructures	<b>Technical Approaches</b>  <pre>graph LR; idea([idea]) --&gt; CAD([CAD]); CAD --&gt; Office[Office]; Office --&gt; Printing[Printing]; Printing --&gt; master([master]); master --&gt; AgX([AgX film]); structure([structure]) --&gt; i1["(i) Electroless deposition"]; i1 --&gt; i2["(ii) Electroplating"]; i2 --&gt; AgX</pre>
<b>Accomplishments</b>  Rapid prototyping metallic structures with >30 $\mu\text{m}$ features: <ul style="list-style-type: none"><li>• Continuous structures</li><li>• Discontinuous structures</li><li>• 3D structures</li><li>• HAR structures</li></ul>	<div>1 mm</div> <div>200 <math>\mu\text{m}</math></div>

## Gold Lines Fabricated using Silver Halide-based film

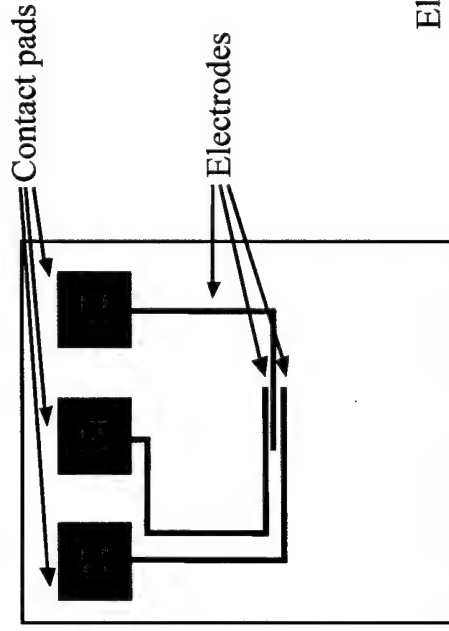


T. Deng, F. Arias, P. Kenis, R. Ismagilov, and G. M. Whitesides

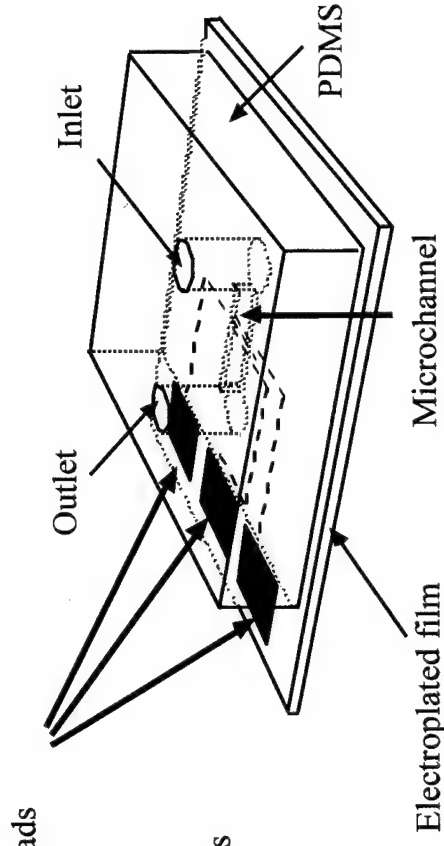


# Electrochemical Detector for Microfluidic Systems

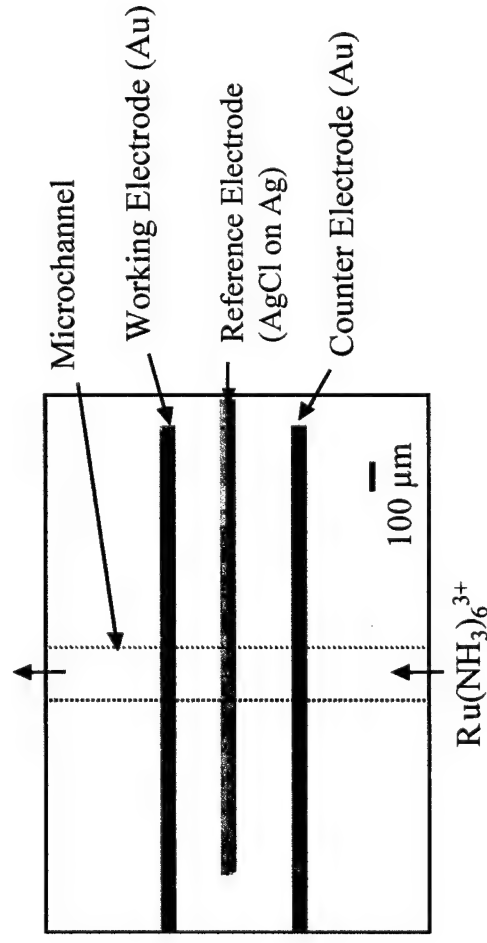
## 1. Design



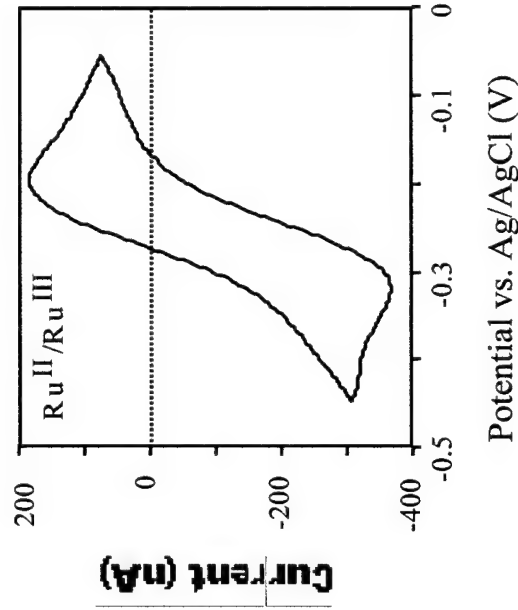
## 2. Three Electrode System



## 3. Magnified view

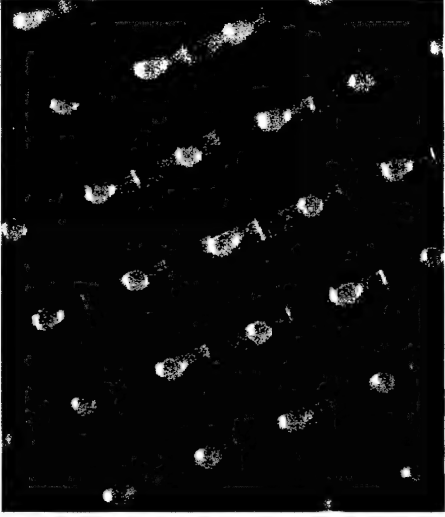


## 4. Cyclic Voltammetry

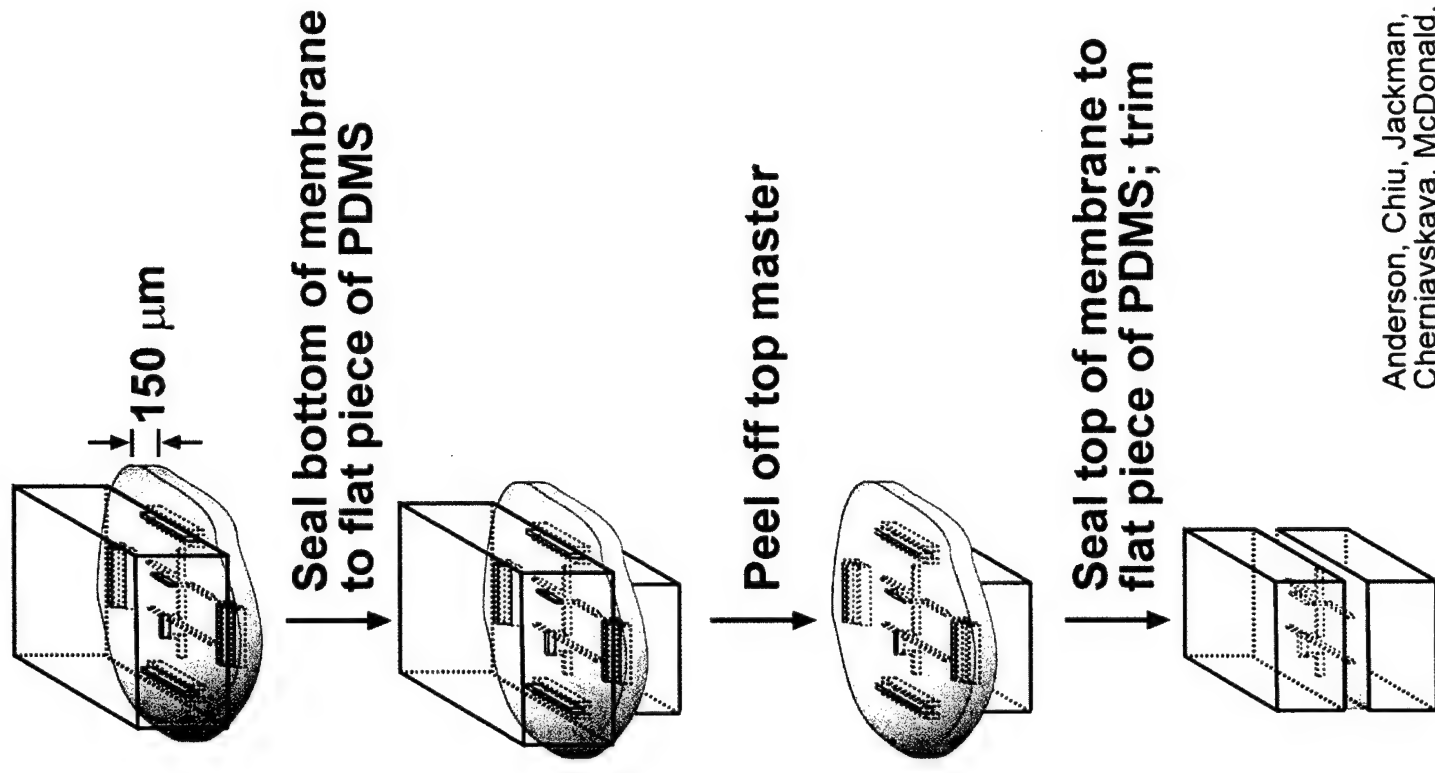
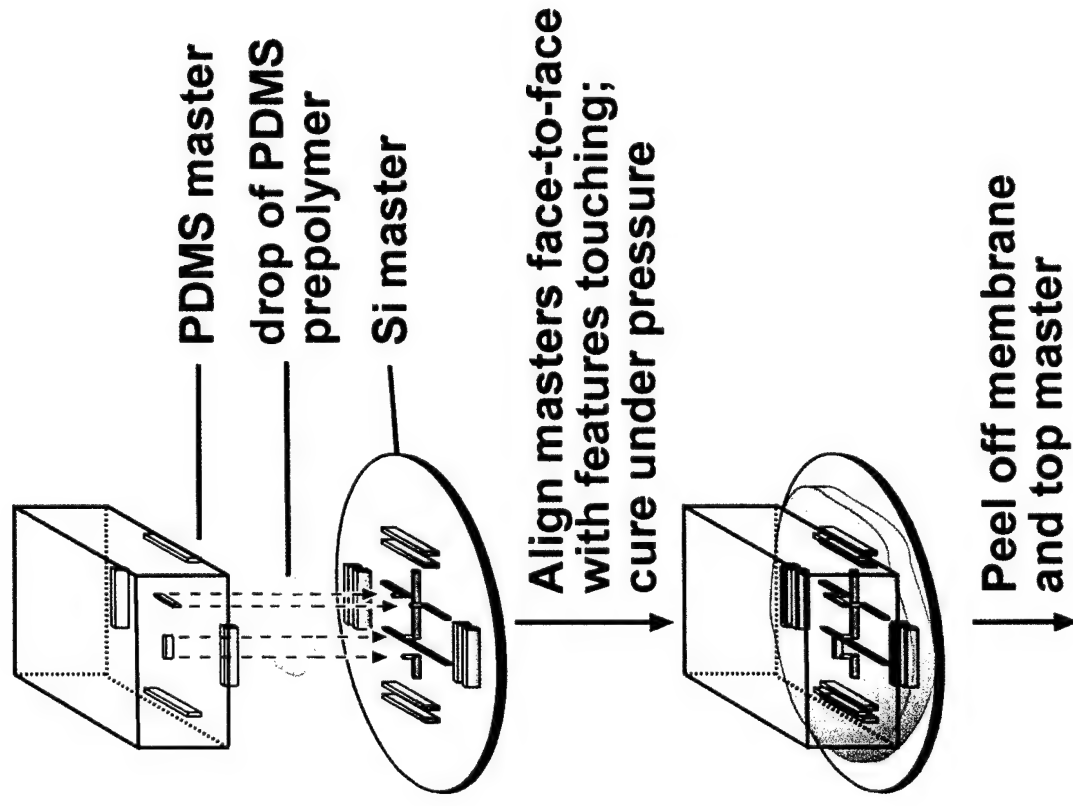


# Fabrication of 3D Microfluidic Systems

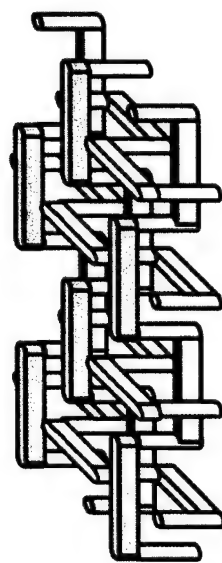
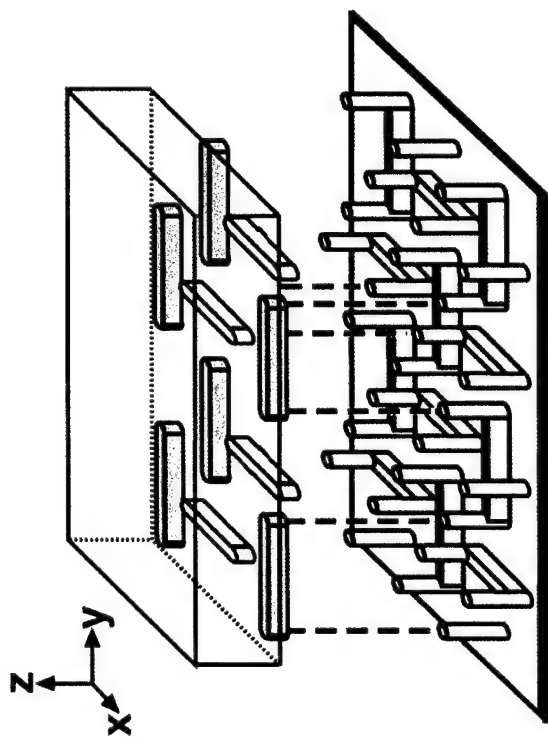
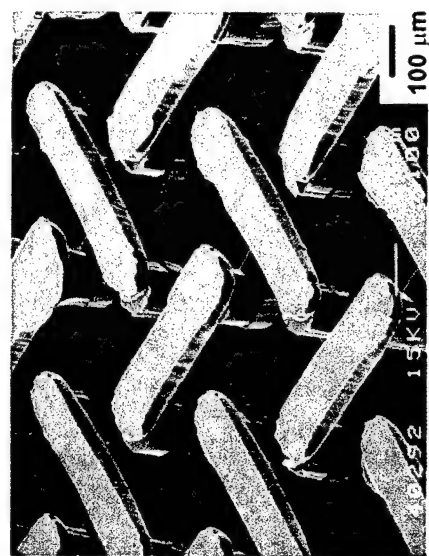
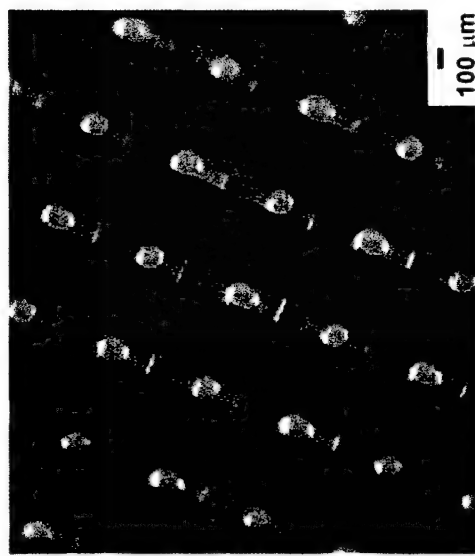
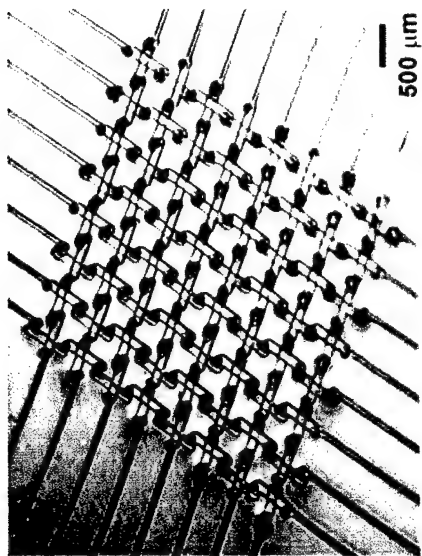
*Anderson, Chiu, Jackman, Cherniavskaya, McDonald, Wu, Whitesides, and Whitesides*  
*Department of Chemistry and Chemical Biology, Harvard University*

<b>Objectives</b> <ul style="list-style-type: none"><li>• To fabricate membranes of PDMS with ~50-100 <math>\mu\text{m}</math> microfluidic channels of any topology</li><li>• To align, stack, and seal these membranes to make a more complicated 3D geometries</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• Rapid Prototyping<ul style="list-style-type: none"><li>• Multi-level Photolithography</li></ul></li><li>• Membrane Sandwich Method</li><li>• Supported Membrane Transfer</li></ul>
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• We make channels in a single membrane that cross over and under each other without intersecting</li><li>• We can make <i>any</i> microfluidic knot</li><li>• We can transfer discontinuous features between substrates without distortion</li></ul>	<p>“Basket weave” system</p>  <p>500 <math>\mu\text{m}</math></p>

# MEMBRANE SANDWICH METHOD

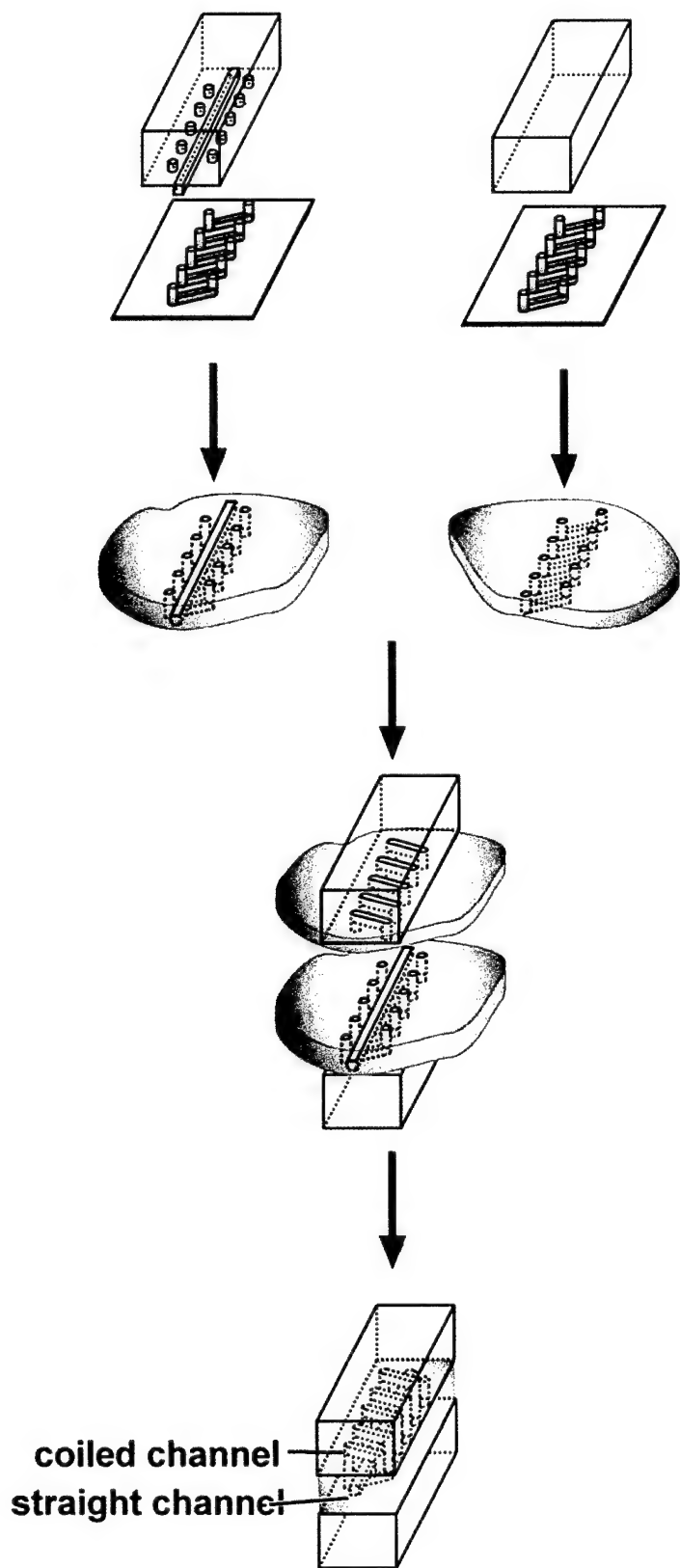


Anderson, Chiu, Jackman,  
Cherniavskaya, McDonald, Wu,  
Whitesides, and Whitesides



channel system

Anderson, Chiu, Jackman,  
Cherniavskaya, McDonald, Wu,  
Whitesides, and Whitesides



Anderson, Chiu, Jackman,  
Cherniavskaya, McDonald, Wu,  
Whitesides, and Whitesides

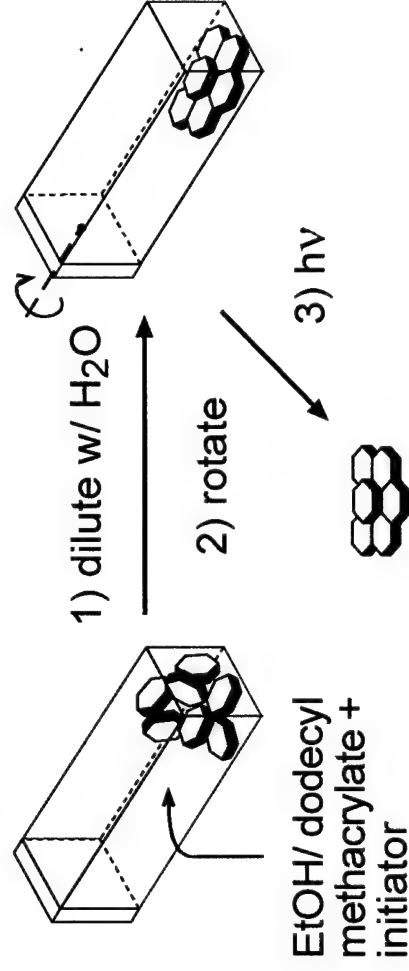
# Three-Dimensional Self-Assembly of Micron-Sized Objects

Joe Tien, Thomas D. Clark, and George M. Whitesides  
Department of Chemistry, Harvard University

## Objective:

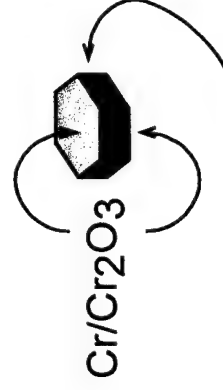
To develop methods for 3-dimensional microfabrication based on self-assembly

## Approach: Crystallization Using Capillarity

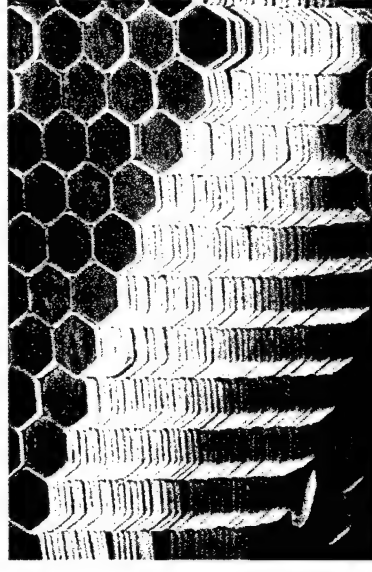


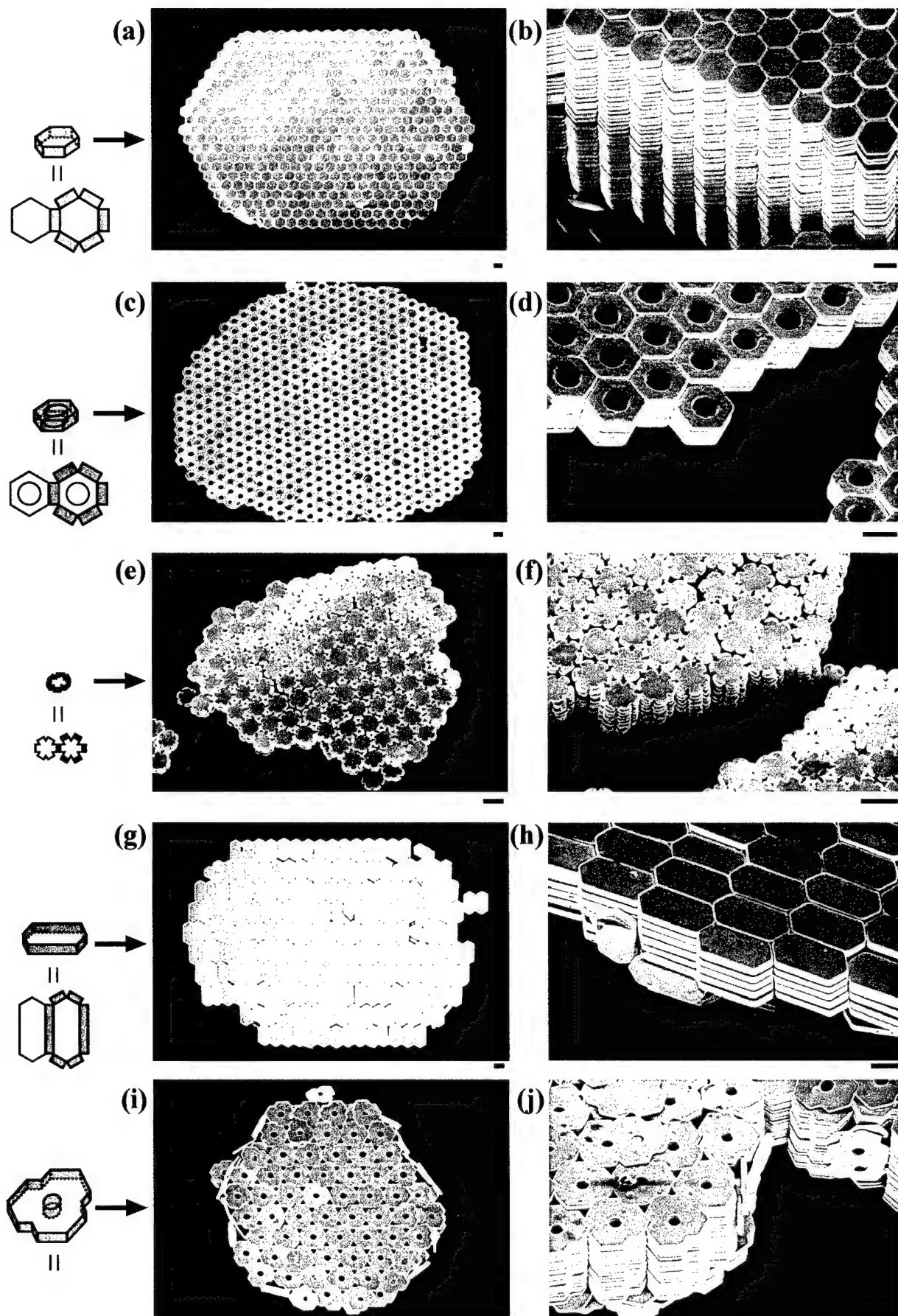
## Accomplishments:

- Facile construction of ordered, 3-dimensional microarrays from non-spherical subunits.
- Bridges gap between colloidal and millimeter-scale self-assembly.
- Likely extendable to other polyhedral components.



Au, covered with  
CH<sub>3</sub>-terminated SAM  
(hydrophobic)

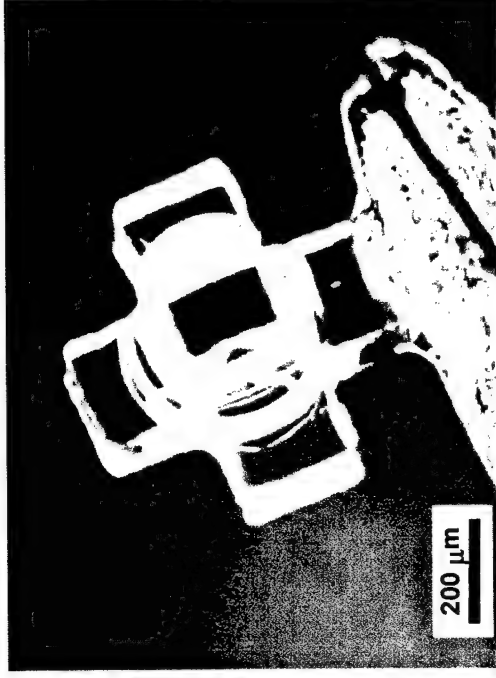




**Figure 2**

# Fabrication of Dali's Crosses

*Hong Yang, Francisco Arias, and George M. Whitesides  
Department of Chemistry & Chemical Biology, Harvard University*

<b>Objectives</b> <ul style="list-style-type: none"><li>• To demonstrate 3D fabrication and use the crosses as building units for self-assembled structures</li></ul>	<b>Technical Approach</b> <ul style="list-style-type: none"><li>• UV-curable prepolymers</li><li>• Multilayer registration</li><li>• Micromolding</li></ul>
<b>Accomplishments</b> <ul style="list-style-type: none"><li>• Fabricated polymeric Dali's crosses</li><li>• Three-level registration to ~ 100 <math>\mu\text{m}</math></li></ul>	



## **Future Directions: Near Term**

### **Microorigami, composites and trusses ( $\mu$ UAVs, read arms)**

- tensegrity structures—incorporation of polymeric elements into metallic, 3D structures
- maximize the stiffness-to-weight ratio of the panels
- use diffusion bonding of nickel instead of tin/lead soldering to assemble sandwich panels

### **Slot filters (thermophotovoltaics)**

- smaller critical dimensions ( $\sim 100$  nm line width)
- fabrication on curved surfaces

### **Heat exchangers (high power microelectronics)**

- modules with high surface area and low thermal resistance
- non-planar heat exchangers

### **Microcontact printing on curved/spherical surfaces**

(curved focal plane IR detector)

- solve the distortion problem for printing on spherical surfaces
- additive methods
- functional components

### **FLO for fabrication of microelectrode systems (BWD)**

- integrated micro-analysis systems
- use for logic/problem solving

### **Dali crosses (photonic bandgap materials)**

- increase yield and quality of the crosses
- modify faces of the crosses and self-assemble into ordered 3D structures

## **Future Directions: Far Term or Technology Base**

Rapid prototyping using Soft Lithography

- generate structures at 1- $\mu\text{m}$  scale

Microelectrochemistry on Saran Wrap (curved surface fabrication)

- quantify and minimize distortion during stretching
- reduce feature size to 1  $\mu\text{m}$

Self-assembly (3D electronic circuits)

- controlling assembly size and shape through templating
- add transistors to the faces
- Self-assembly of photonic bandgap crystals

Rapid prototyping using silver halide film

- smaller structures; more functional applications, color films

Ceramics (rapid microfabrication of complex ceramic microstructures)

- C/Si: new start to convert Si layer on glassy C to SiC
- Si/B/C/N: improve fidelity; fabricate useful structures such as membranes and microcomponents

3D microfabrication in microfluidic systems (BWD)

- apply methods to systems that require compactness or have topological constraints
- generate complex fluidic components

# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***Micropatterning through Field-Assisted Flow***

**ILHAN A. AKSAY<sup>\*,§</sup>, GEORGE M. WHITESIDES<sup>†</sup>, SOL M. GRUNER<sup>‡</sup>,  
ROBERT K. PRUD'HOMME<sup>\*,§</sup>, DUDLEY A. SAVILLE<sup>\*,§</sup>,  
JAMES S. VARTULI<sup>\*,§</sup>, DANIEL M. DABBS<sup>\*,§</sup>, MATT TRAU<sup>§</sup>,  
SRINIVAS MANNE<sup>§</sup>, LINBO ZHOU<sup>#</sup>, ANTHONY KU<sup>\*,§</sup>,  
HAK FEI POON<sup>\*,§</sup>, MACIT ÖZENBAS<sup>§</sup>**

**DEPARTMENTS OF \*CHEMICAL ENGINEERING, #PHYSICS, AND  
§PRINCETON MATERIALS INSTITUTE  
PRINCETON UNIVERSITY, PRINCETON, NEW JERSEY 08544**

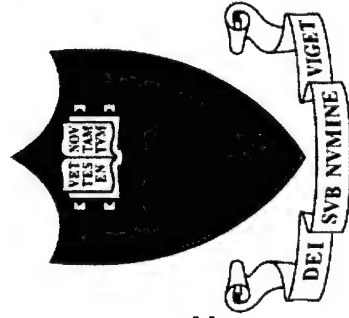
**<sup>†</sup>DEPARTMENT OF CHEMISTRY, HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS 02138**

**<sup>‡</sup>DEPARTMENT OF PHYSICS, CORNELL UNIVERSITY  
ITHACA, NEW YORK 14853**

## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**



Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

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# Patterning through Field-Assisted Flow

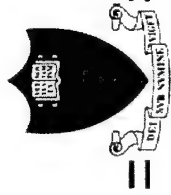
Ilhan A. Aksay,<sup>§</sup> George M. Whitesides,<sup>#</sup> Dudley A. Saville,<sup>§</sup>

Daniel M. Dabbs,<sup>§</sup> Matt Trau,<sup>§</sup> Linbo Zhou,<sup>‡</sup> Anthony Ku,<sup>§</sup>  
Hak-Fei Poon,<sup>§</sup> and Macit Özenbas<sup>§</sup>

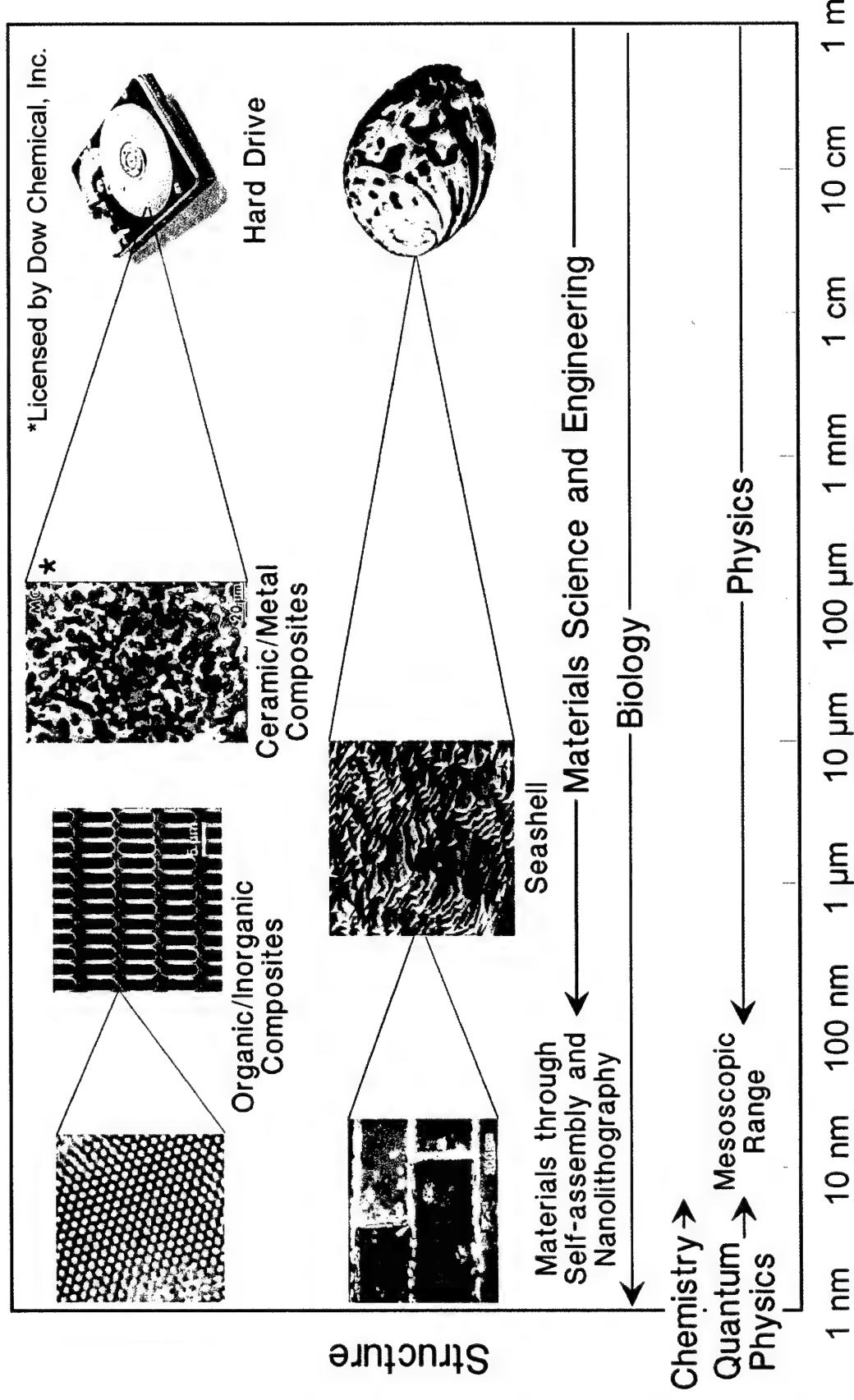
Departments of <sup>§</sup>Chemical Engineering, <sup>‡</sup>Physics,  
and Princeton Materials Institute,  
Princeton University

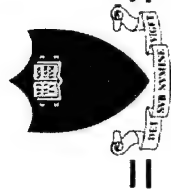
<sup>#</sup>Department of Chemistry, Harvard University

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# Scale of Materials Processing

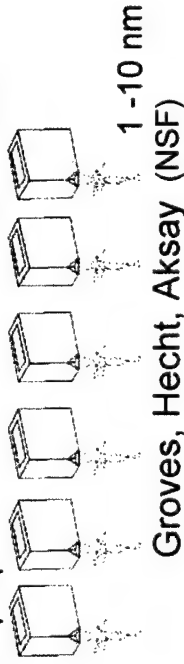




# Goals and Organization

## Self Assembly

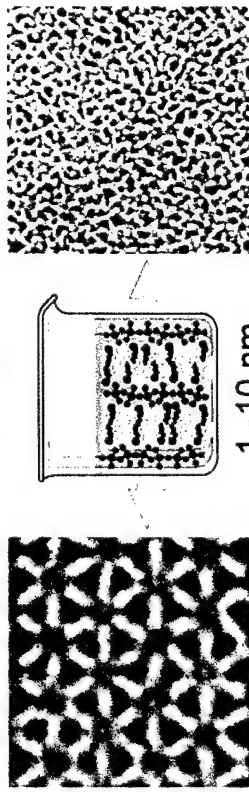
(a) Amphiphilic and Protein Membranes



1 - 10 nm

Groves, Hecht, Aksay (NSF)

(b) Liquid Crystal Templating



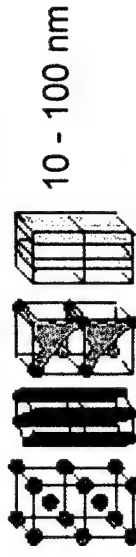
Cubic phase

1 - 10 nm

Sponge phase

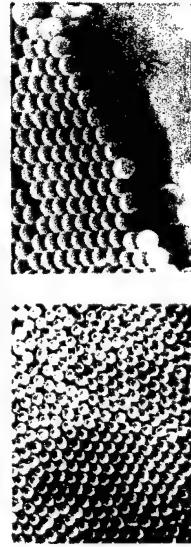
Dabbs, Saville, Aksay

(c) Block Copolymer Templating (NSF)



10 - 100 nm

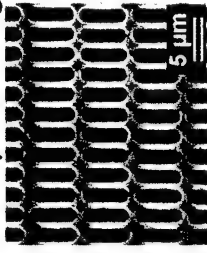
(d) 2D and 3D Colloidal Structures



Saville, Aksay

## Laminating and Micropatterning by Field-Assisted Flow

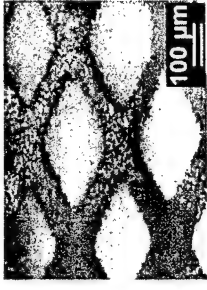
(a) Micropatterning



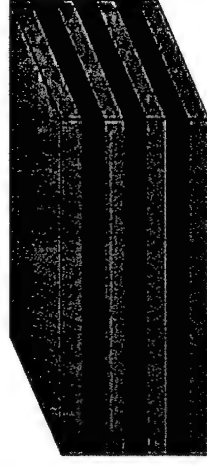
(b) Cone/Jet



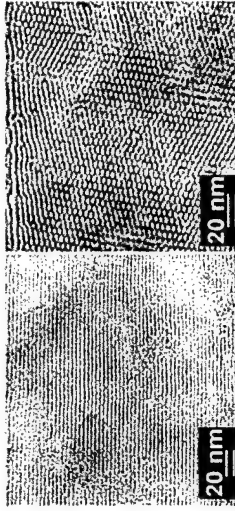
(c) Electrodeposition

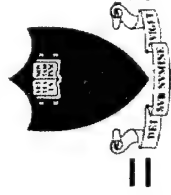


## OPTIMAL PROPERTIES



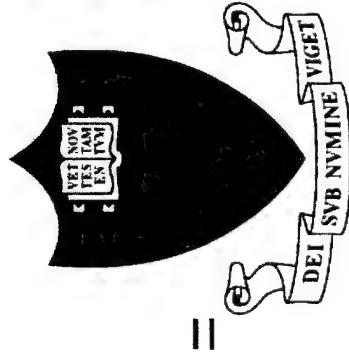
Hierarchically Structured  
Nano- and Microlaminates  
Suo, Evans, Sobojejo, Saville,  
Groves, Aksay (NSF)





# Patterned Thin Films and 3D Structures

- **Goals**
  - Develop nanostructured ceramic/organic composites through self-assembly
  - Develop patterned structures for device applications
- ***Conventional Approach***
  - Deposit continuous ceramic films followed by etching
    - ◆ Photolithographic resolution is large ( $>0.1\text{ }\mu\text{m}$ )
    - ◆ Expensive and hazardous etchants



Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

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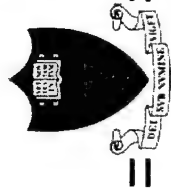
# **Confinement Patterning: Simultaneous Patterning at Multi-Length Scales**

**Anthony Y. Ku, Linbo Zhou,  
Dudley A. Saville,\* Peter Eisenberger,\*  
George M. Whitesides, and Ilhan A. Aksay**

*\*Partial support from the NSF/MRSEC (DMR 94-00362 and DMR 98-09483)*

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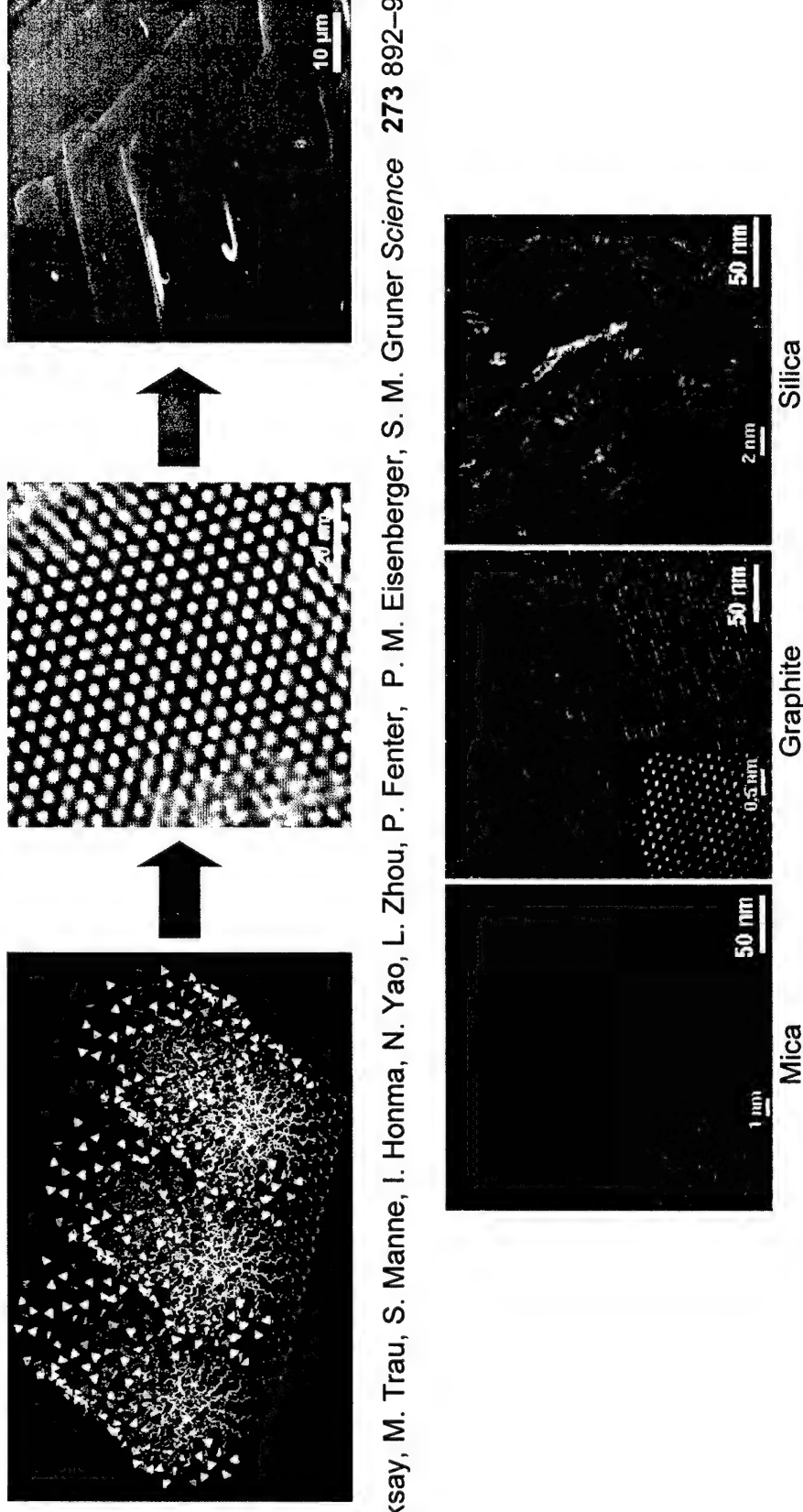




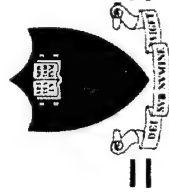
# Mesostuctured Inorganics through Liquid Crystal Templating

## •*Surfactant-based procedure yields mesostructured inorganic materials*

C. T. Kresge *et al.*, *Nature* **359** (1992); and, J. S. Beck *et al.*, *J. Am. Chem. Soc.* **114** [27] (1992).



I. A. Aksay, M. Trau, S. Manne, I. Honma, N. Yao, L. Zhou, P. Fenter, P. M. Eisenberger, S. M. Gruner Science **273** 892–98 (1996).

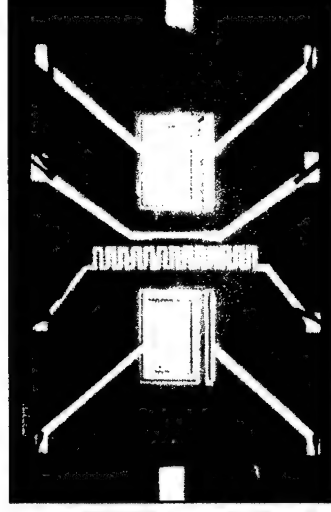


# Projected and Actual Applications

## Biocomposites

- artificial coral<sup>1</sup>
- bioreactor frameworks

## Catalysis<sup>2</sup>



## Low dielectric films<sup>3</sup>

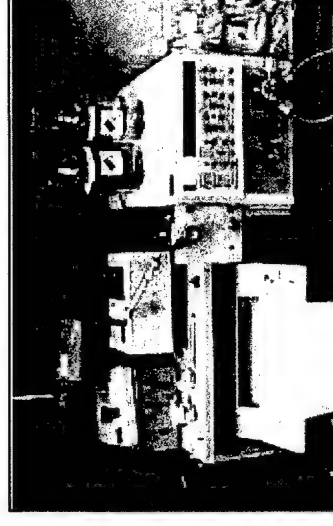
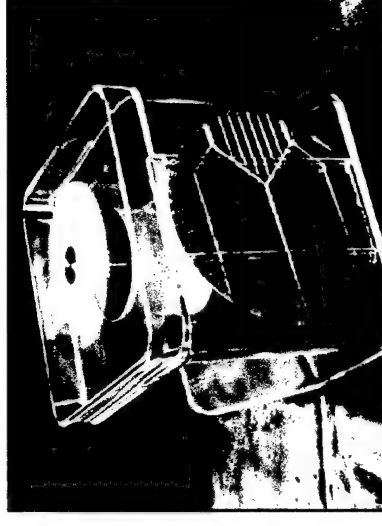
## Nanoelectronics

- lasers<sup>1</sup>
- memory components

## Sensors

## Separations

- biological
- environmental<sup>1,3-4</sup>
- HPLC column packing<sup>4</sup>
- others (embedded films<sup>3</sup>)

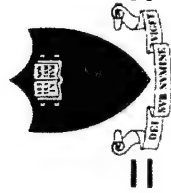


<sup>1</sup> UC-Santa-Barbara

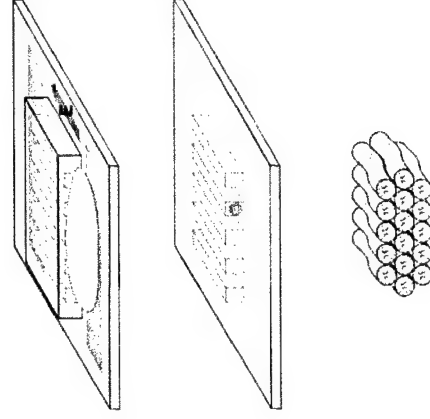
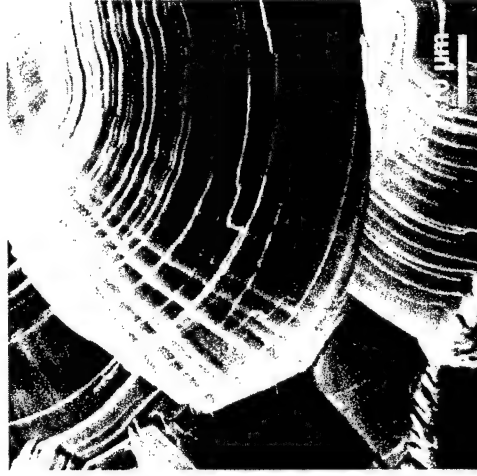
<sup>2</sup> Mobil Oil Company

<sup>3</sup> Pacific Northwest National Lab

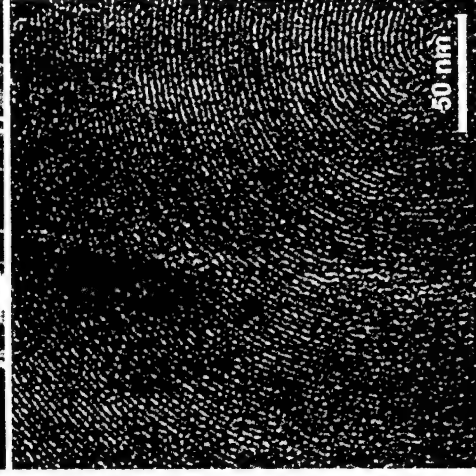
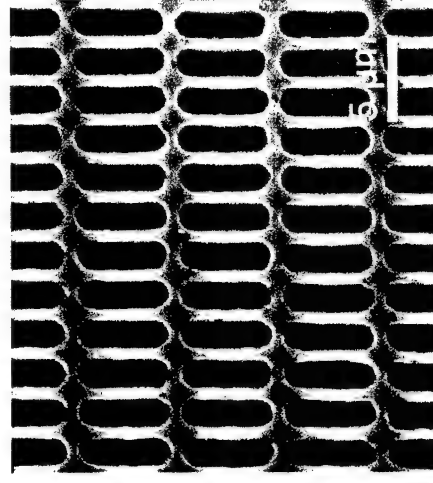
<sup>4</sup> Los Alamos National Lab



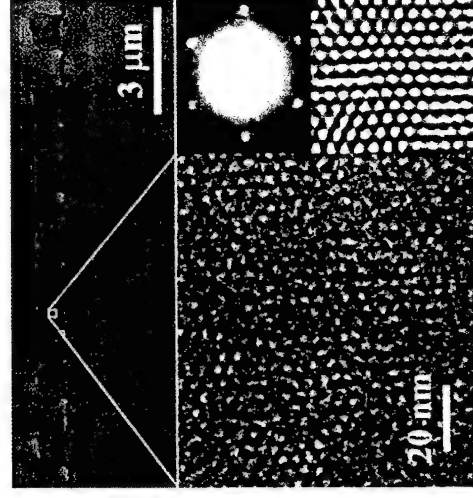
# Nanocomposite Organic/Inorganic Materials through Self-assembly



Micropatterning

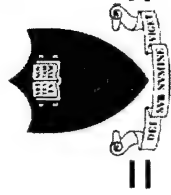


Hexagonal  
Phase

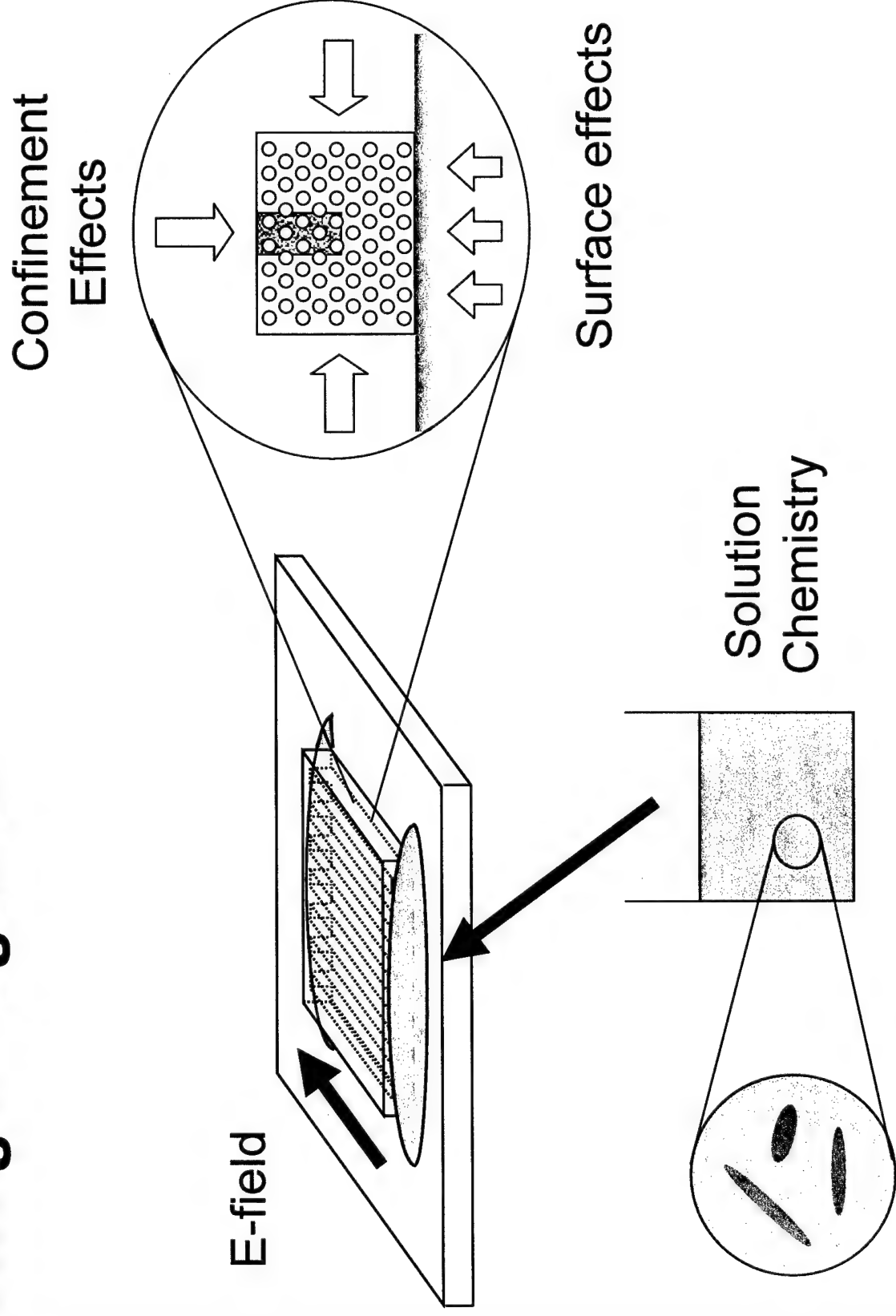


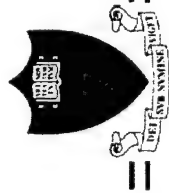
I. A. Aksay, M. Trau, S. Manne, I. Honma, N. Yao, L. Zhou, P. Fenter, P. M. Eisenberger, and S. M. Gruner *Science* **273** 892-98 (1996).

M. Trau, N. Yao, E. Kim, Y. Xia, G. M. Whitesides, I. A. Aksay, *Nature* **390** 674-6 (1997).

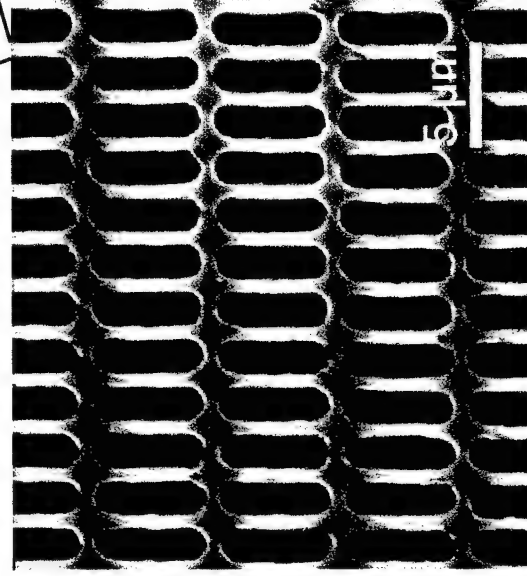
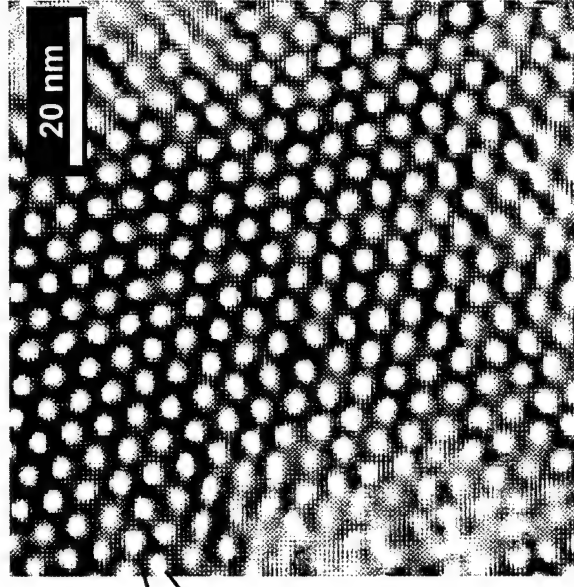
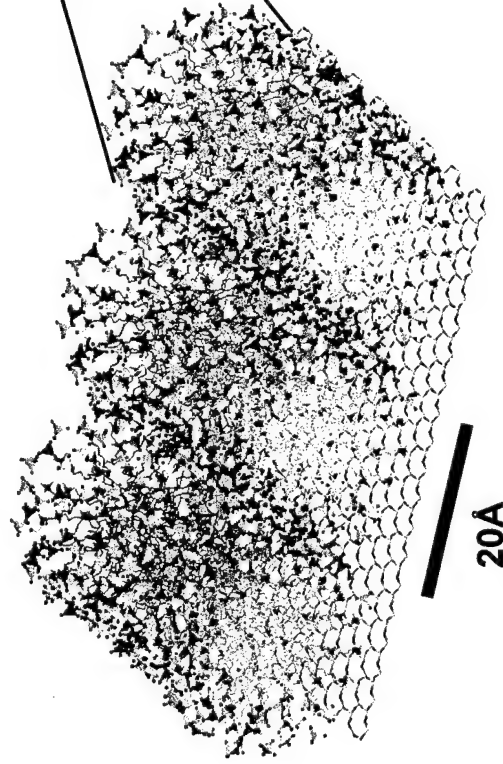


# Putting It Together...



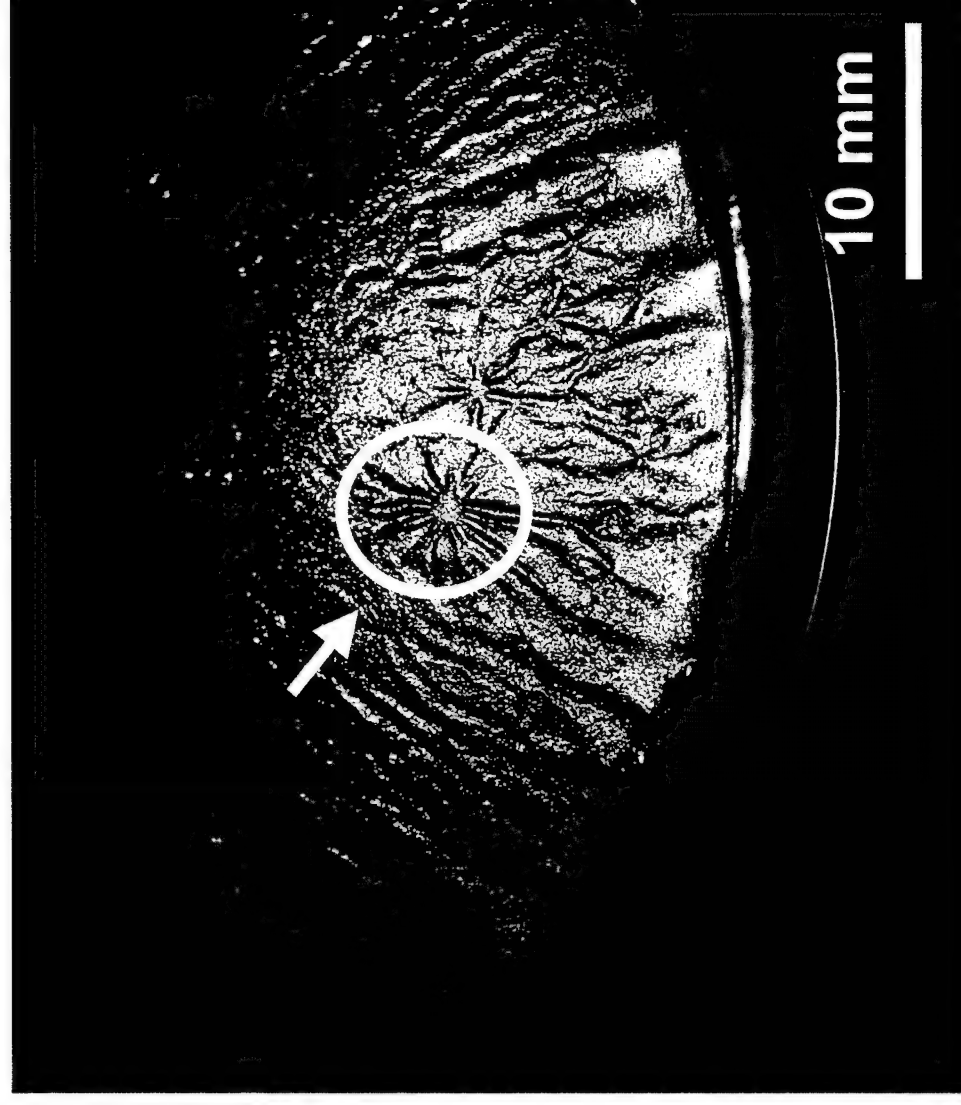
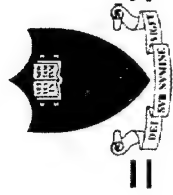


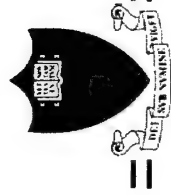
# Simultaneous Patterning at Multi-Length Scales



I. A. Aksay, M. Trau, S. Manne, I. Honma,  
N. Yao, L. Zhou, P. Fenter, P. M. Eisenberger,  
and S. M. Gruner *Science* **273** 892-98 (1996);

M. Trau, N. Yao, E. Kim, Y. Xia,  
G. M. Whitesides, and I. A. Aksay, *Nature* **390**  
[6661] 674-76 (1997)

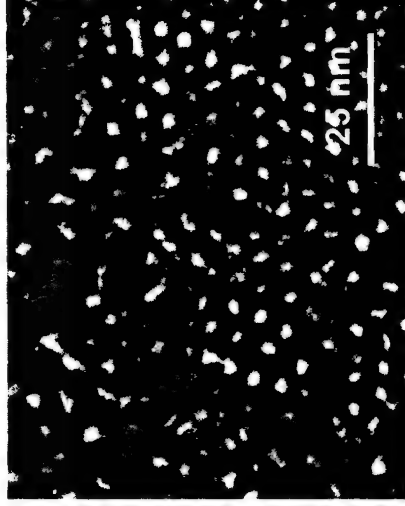




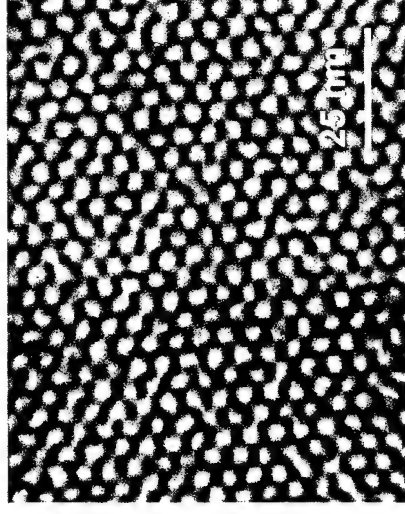
# Film Growth: Mesoscopic Crystallization



30 minutes

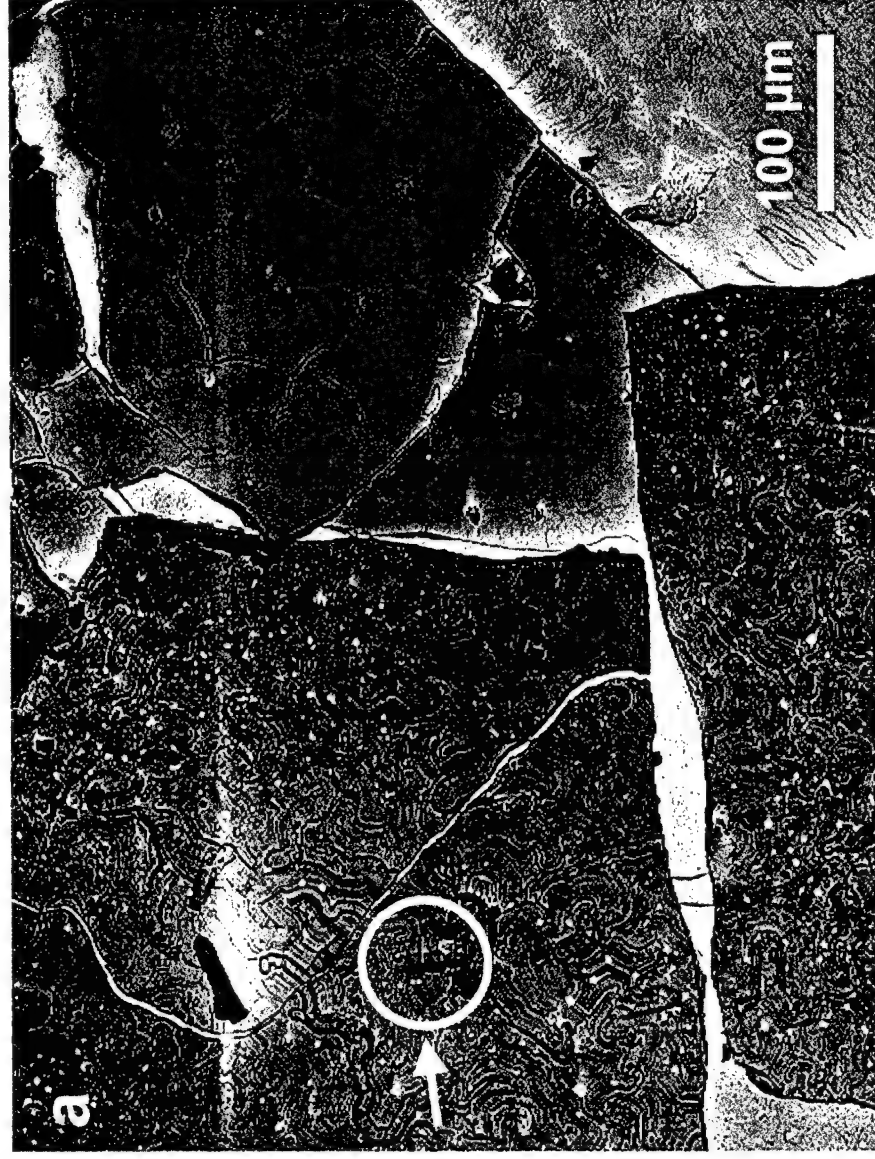
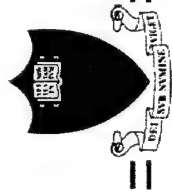


5 hours

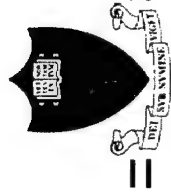


2 days

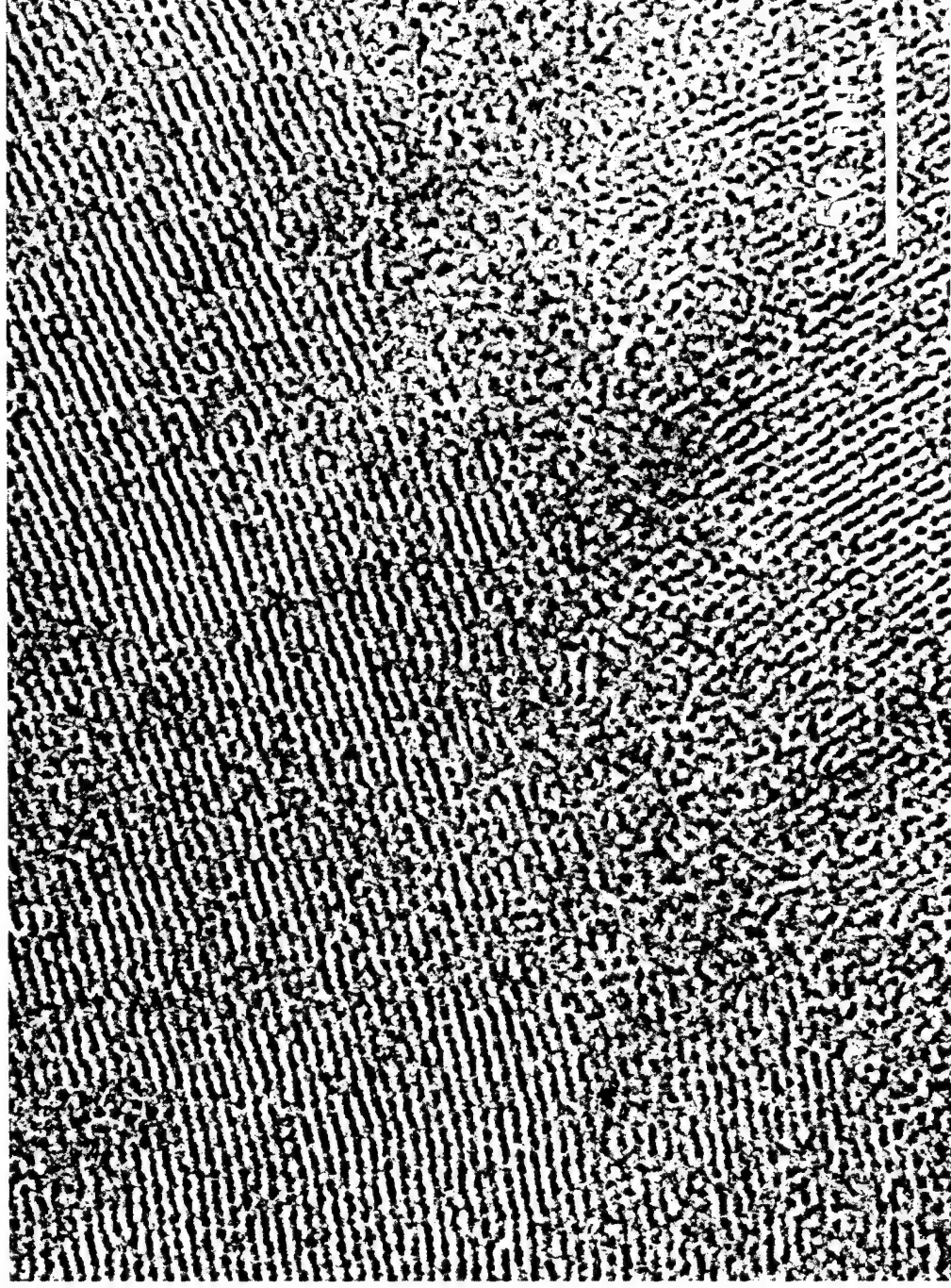






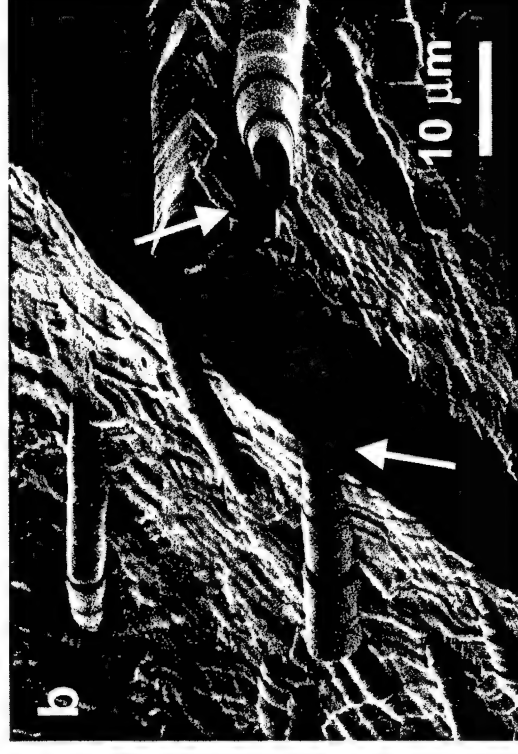
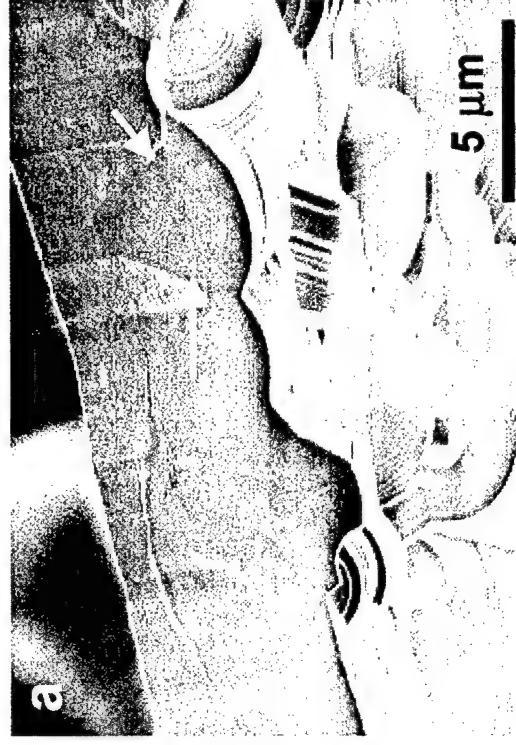
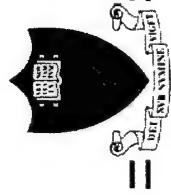


# Cross-Sectional TEM: Film at the Air-Water Interface

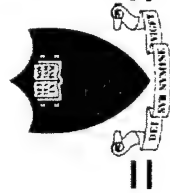


N. Yao, A. Y. Ku, H. Nakagawa, T. Lee, D. A. Saville, and I. A. Aksay, submitted to *Langmuir* (1999)

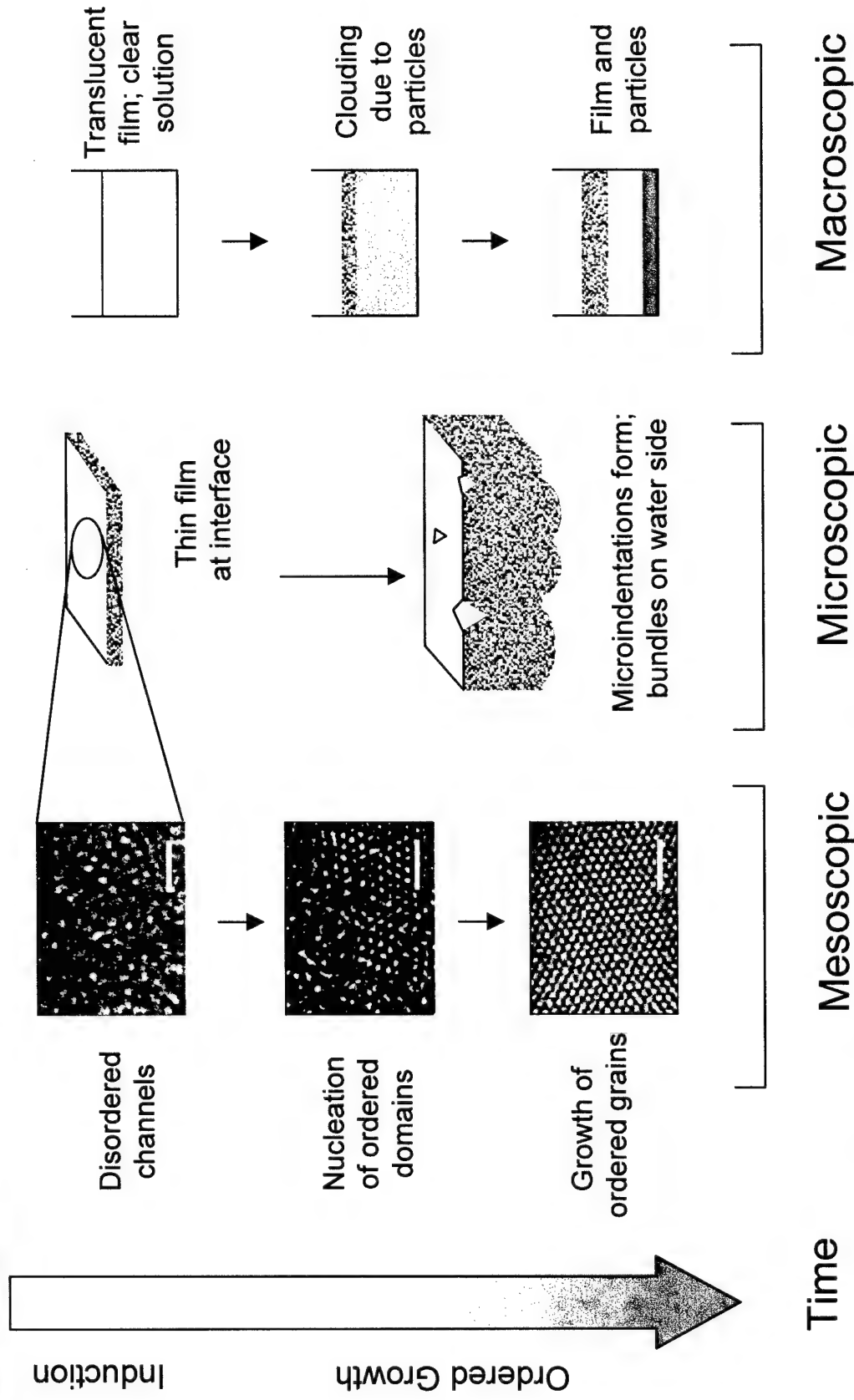
---

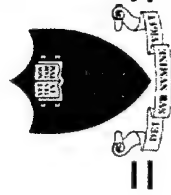


N. Yao, A. Y. Ku, H. Nakagawa, T. Lee, D. A. Saville, and I. A. Aksay, submitted to *Langmuir* (1999)

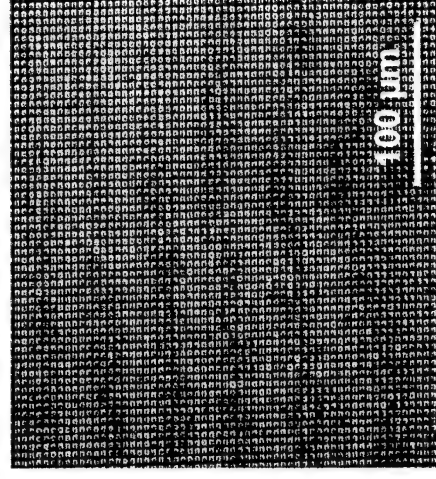
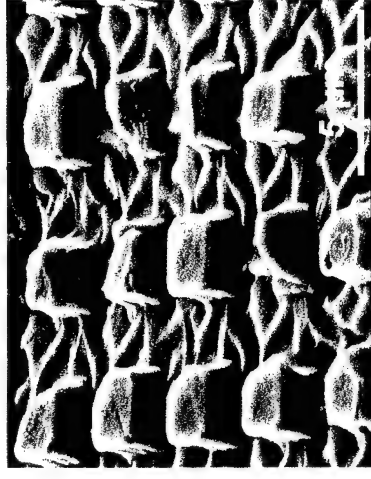
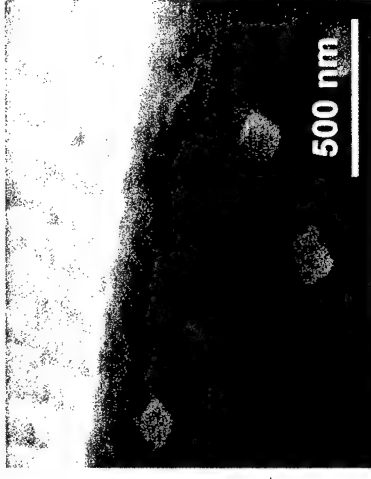
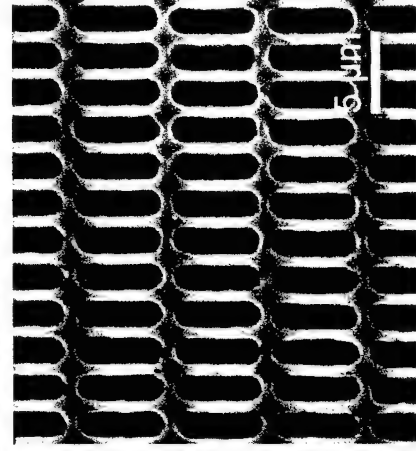
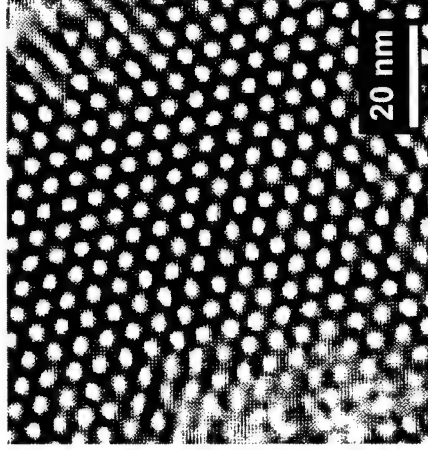
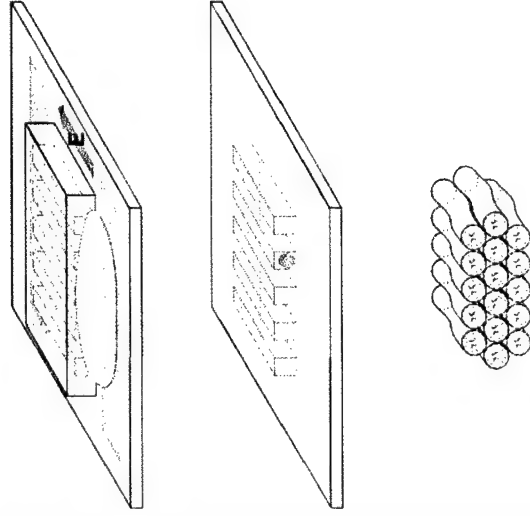


# Mechanism: Film Growth at the Air-Water Interface

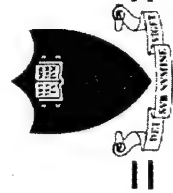




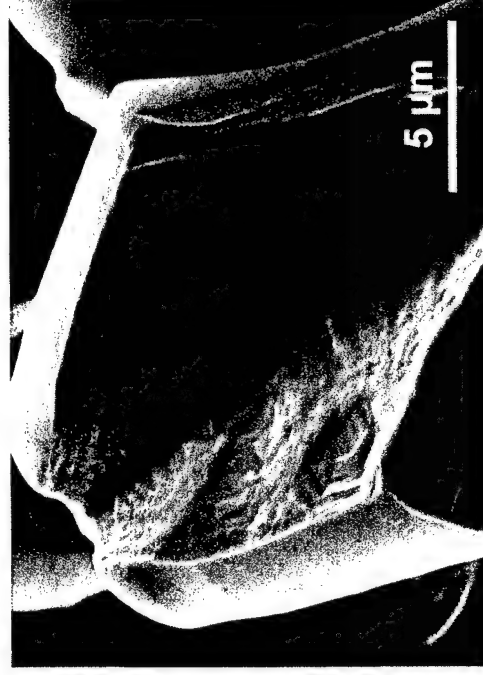
# Liquid Crystal Templating

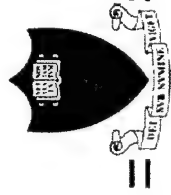


I. A. Aksay, M. Trau, S. Manne,  
I. Honma, N. Yao, L. Zhou, P. Fenter,  
P. M. Eisenberger, S. M. Gruner,  
*Science* **273** 892–98 (1996);  
M. Trau, N. Yao, E. Kim, Y. Xia,  
G. M. Whitesides, I. A. Aksay,  
*Nature* **390** [6661] 674-76 (1997)  
A. Y. Ku, D. A. Saville, I. A. Aksay,  
unpublished research (1999)



# Particle Growth: Mesoscopic Crystallization

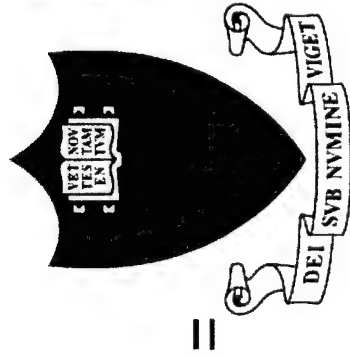




## Mechanism: Future Directions

- ***Strategic***
  - Target mesoscopic crystallization stage
  - Use surface effects to orient nuclei
- ***New approaches***
  - Apply field (E, B, shear) during mesophase formation
  - Use surface effects to influence domain orientations





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Princeton Materials Institute  
Princeton University

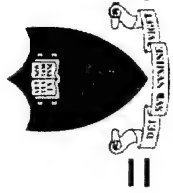
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# **Electrohydrodynamic Printing: Cone-Jet Transition in an Electric Field**

**Hak Fei Poon, Dudley A. Saville,\* and  
Ilhan A. Aksay**

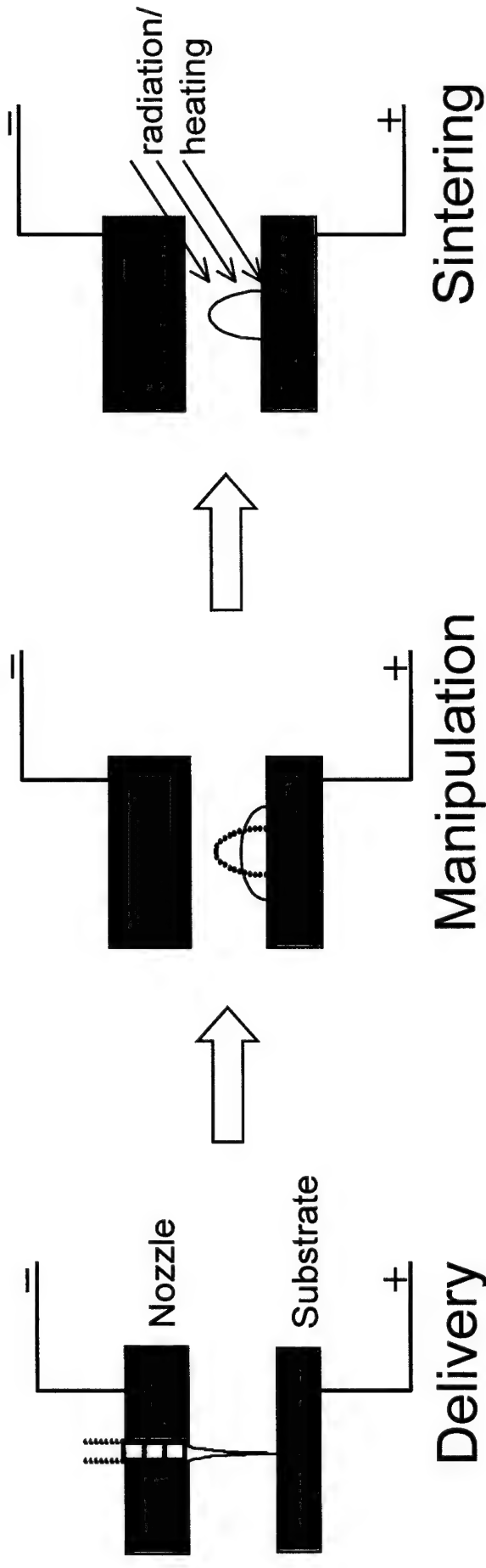
*\*Partial support from the NSF/MRSEC (DMR 94-00362 and DMR 98-09483)*

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# Electrohydrodynamic (EHD) Printing

- *Objective*
  - Develop a technique for microscale material decoration using electrohydrodynamic principles
- *Approach: Field-assisted flow combined with ink-jet printing*

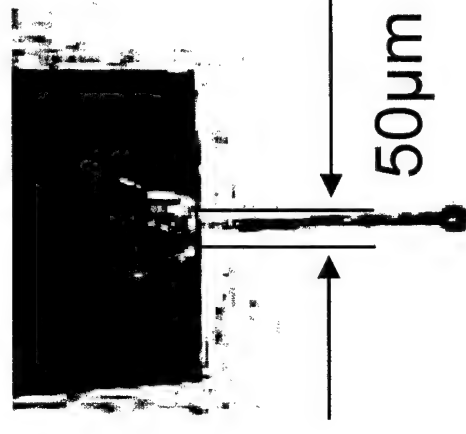




# Ink Jet Technology vs. EHD Jet Printing

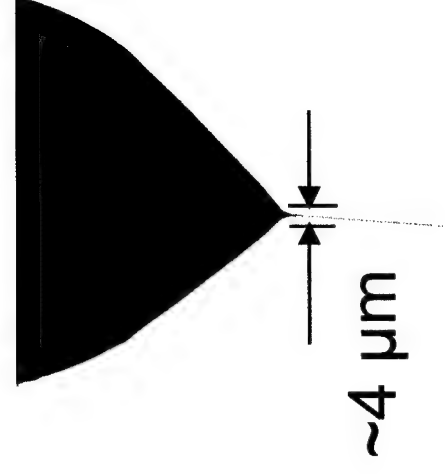
- *Inkjet technology:*

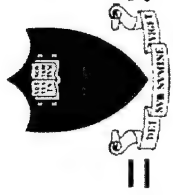
- Resolution: 1200–1400 dpi ~ 15–20  $\mu\text{m}$
- Drop size ~ order of channel size
- Reducing channel size causes clogging with colloidal suspensions



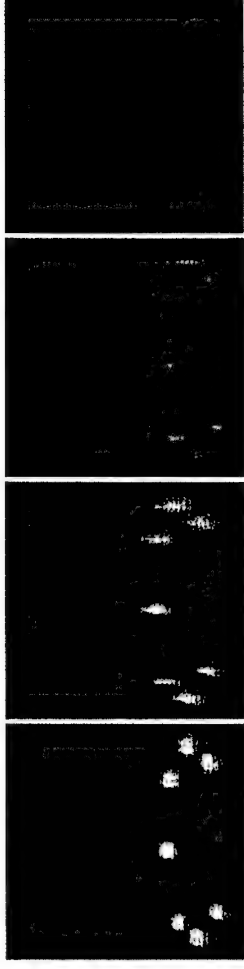
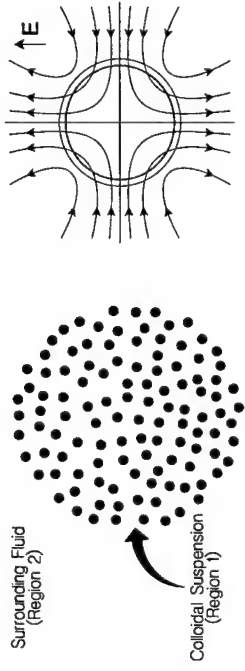
- *EHD printing*

- Drop size ~ two orders of magnitude smaller than the channel size
- No clogging



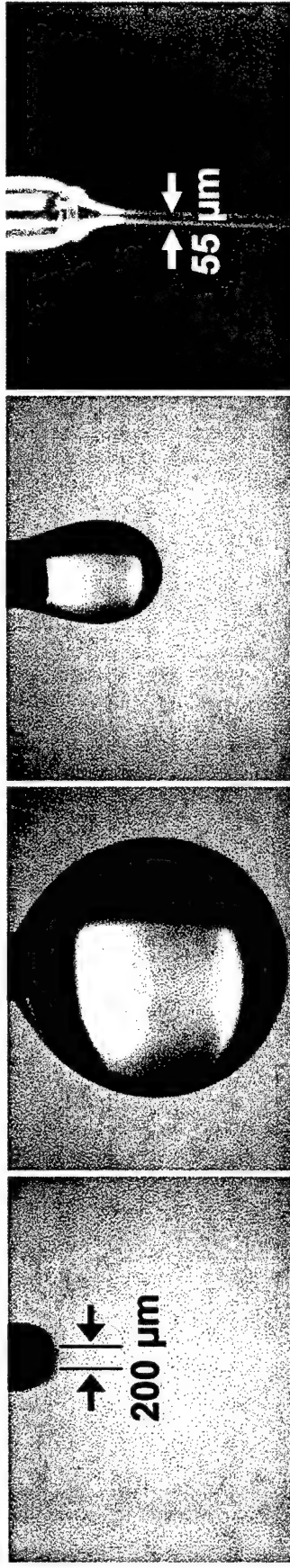


# Electrohydrodynamic Printing



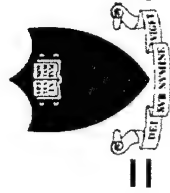
D. A. Saville, *Phys. Rev. Letts.* **71** (1993).

M. Trau, S. Sankaran, D.A. Saville, I.A. Aksay, *Nature* **374** 437-9 (1995);  
M. Trau, S. Sankaran, D.A. Saville, I.A. Aksay, *Langmuir* **11** 4665-72 (1995).



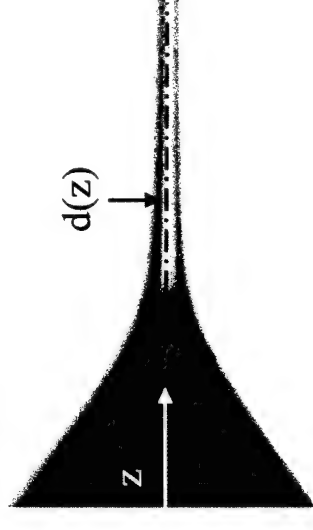
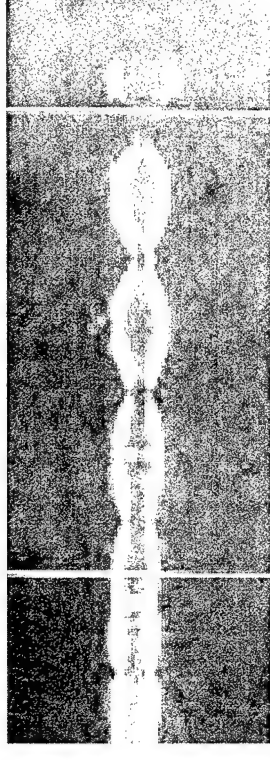
## • Issues

- Balance of interfacial tension and e-forces
- Smallest diameter 100 nm (?)
- Deployment, spreading, solidification -- control by e-forces shaped electrodes
- Balance fluid properties with particles to produce a filament, deploy it, ...

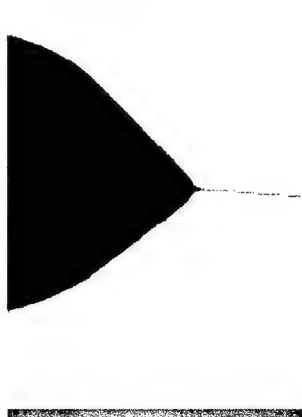
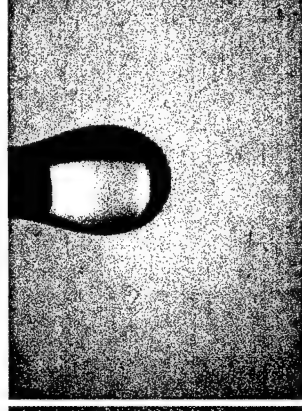
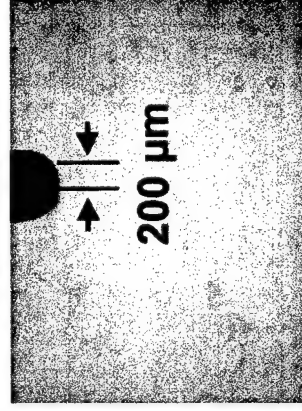


# What is Cone-Jet Transition

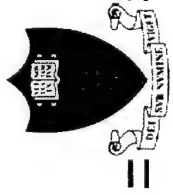
- Capillary jet instability (Rayleigh, 1878)
- Cone jet transition (Zeleny, 1915, 1917)
- Taylor's model (1964) - electrical and surface tension force
- De la Mora et al. (1993):  
 $I \sim Q^{1/2}$ ,  $d \sim Q^{1/3}$



Nozzle      Drop      Cone      Jet

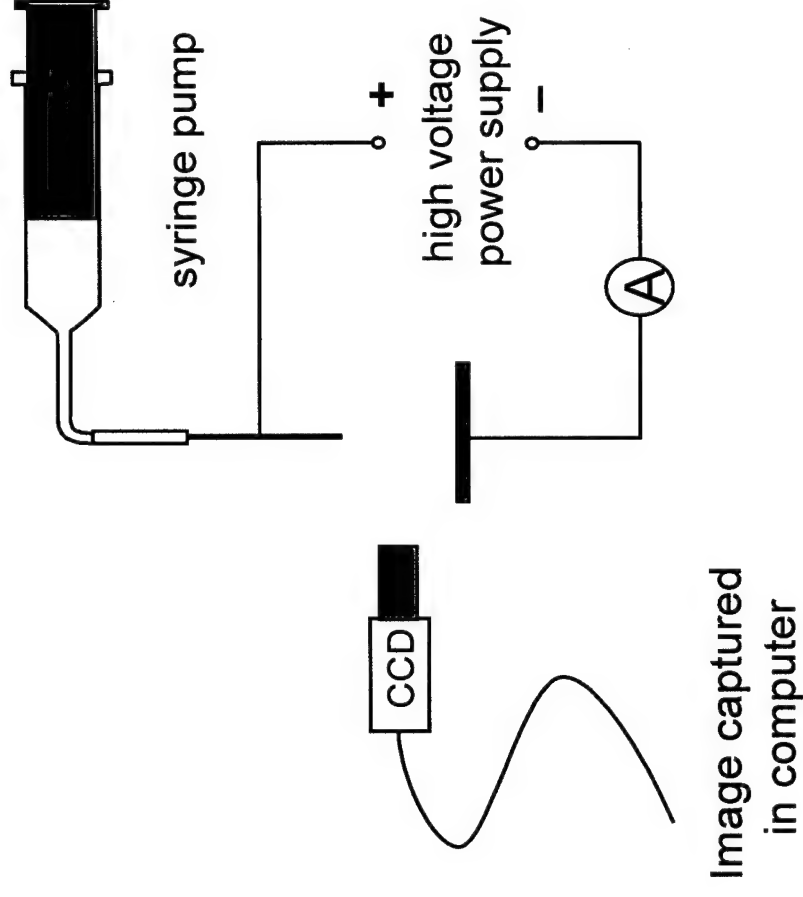


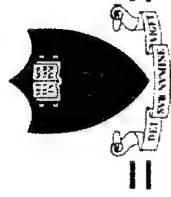
———— Increasing Electric Field ———→



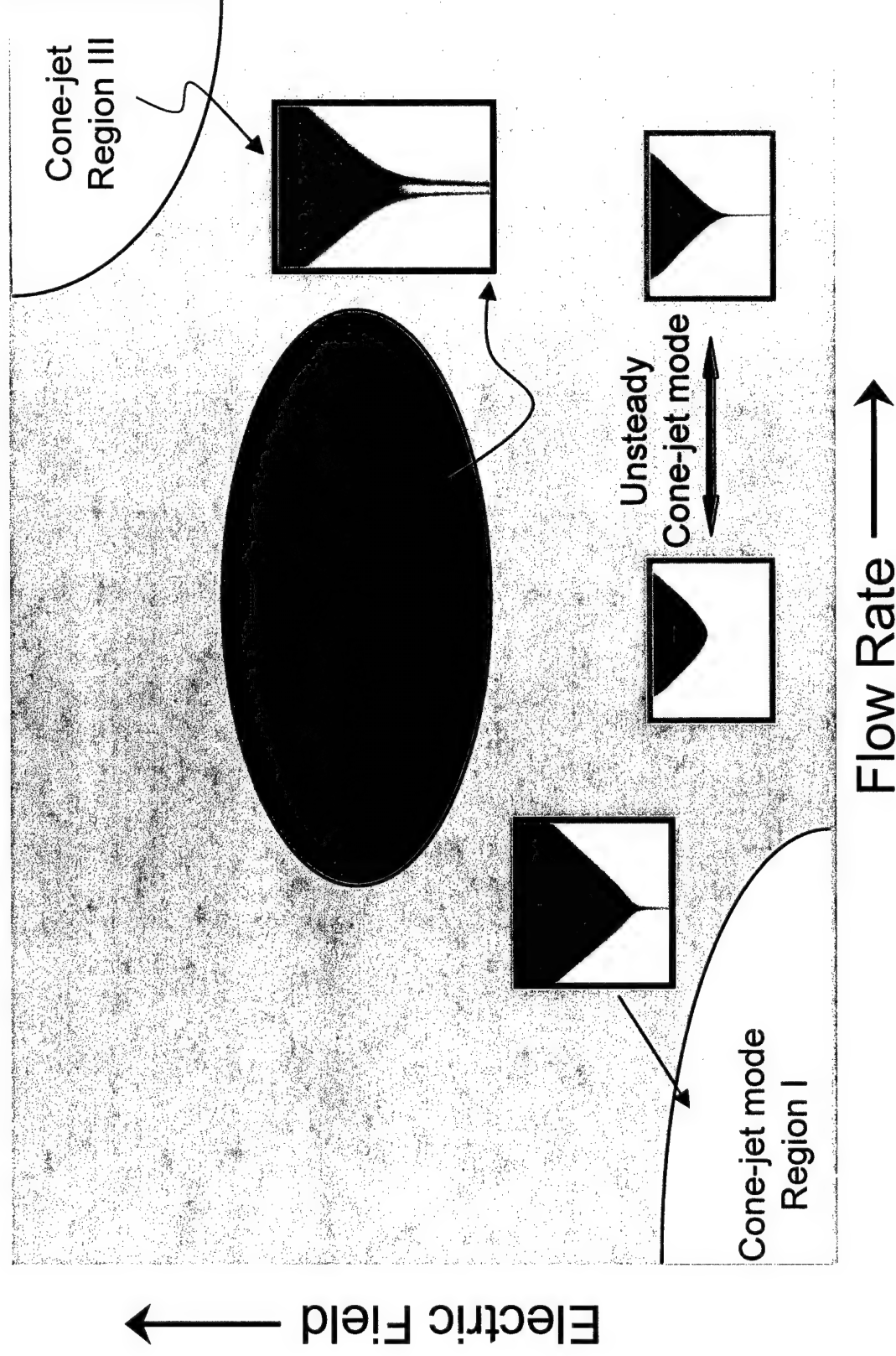
# Elements of the Investigation

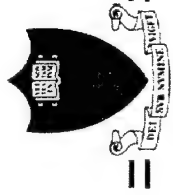
- *Direct measurement of of jet size*
- *Re-examination of the cone jet transition*
- *Identification of a new regime where current and droplet diameter follow different scaling laws*





# Cone-Jet Transition Phase Diagram

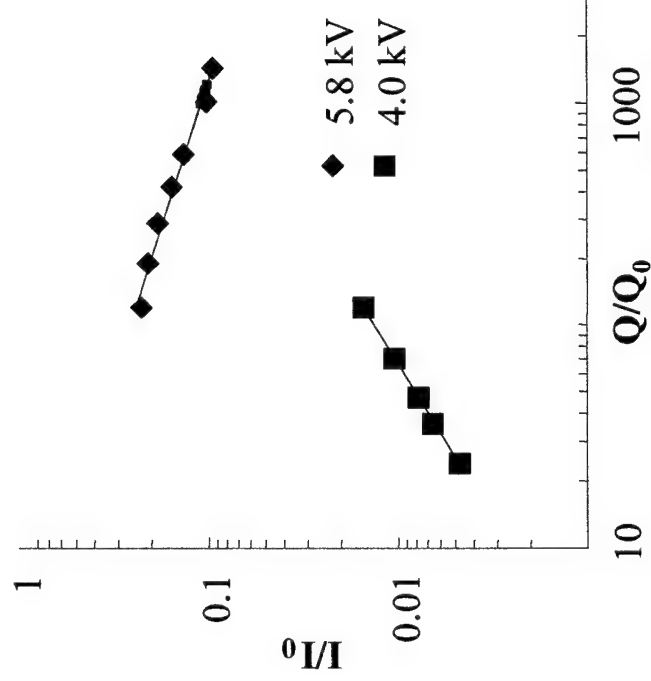




# New Large Flow, High Current Regime

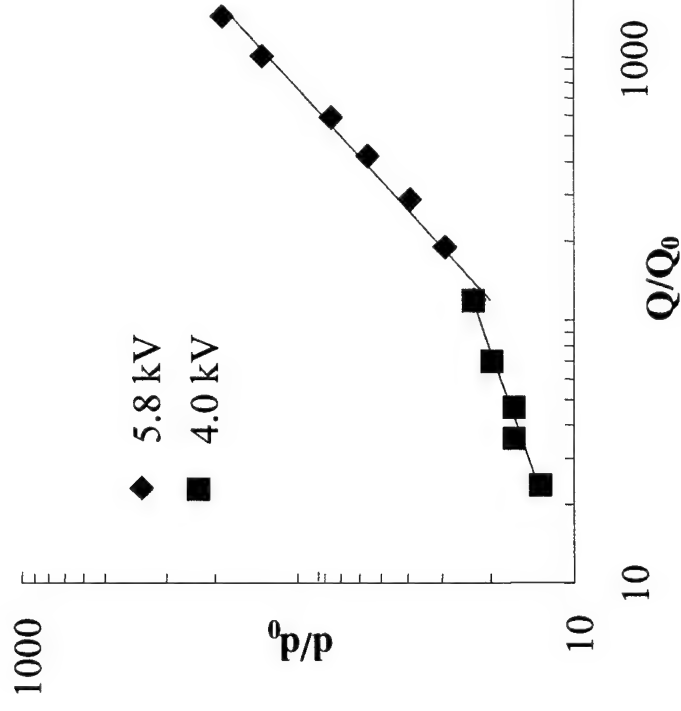
## • De la Mora's Model

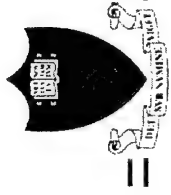
- Low flowrate, low current regime  
 $I \sim Q^{1/2}$ ,  $d \sim Q^{1/3}$
- Experimentally confirmed



## • New regime

- Large flowrate, high current regime  
 $I \sim Q^{-0.3 \sim -0.4}$ ,  $d \sim Q^{0.8 \sim 0.9}$





## Discussion

- ***A Consistency Check - Scaling Analysis:***

**Convection Current:**  $I \sim \pi d u_s \rho_s$  - *bulk conduction negligible*  
**Surface Velocity:**  $u_s \sim 4Q/d^2$  - *for a slender jet with flat velocity profile*

**Surface Charge Density:**  $\rho_s \sim \epsilon \epsilon_0 E_n^0 \sim \epsilon \epsilon_0 (2\gamma/\epsilon \epsilon_0 d)^{1/2}$

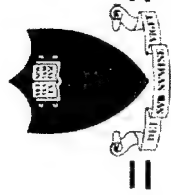
$$\Rightarrow I/Q \sim d^{-3/2}$$

**check:**

***For the large flow, high current regime, take***

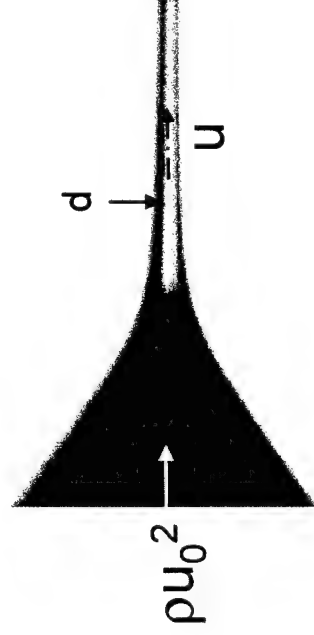
$$I \sim Q^{-0.3}, d \sim Q^{0.9}$$

$$I/Q \sim Q^{-0.3}/Q \sim Q^{-1.3} \sim (Q^{0.9})^{-3/2} \sim d^{-3/2}$$

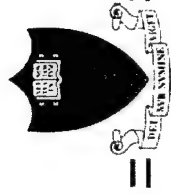


# Comparison and Explanation

$u \sim Q^\alpha$	$\alpha$	Jet diameter, $d \sim (Q/u)^{1/2}$	Comments
Delamora et al. (1993)	1/3	$d \sim Q^{1/3}$	Agree well at low flow rate when dynamic pressure at the entrance of nozzle are negligible
Ganan Calvo et al. (1994)	0	$d \sim Q^{1/2}$	
Our finding	<0	$d \sim Q^{0.9}$	Gaining significance of dynamic pressure at increased flow rate $\Rightarrow$ i) $d \uparrow$ ii) $u \downarrow$



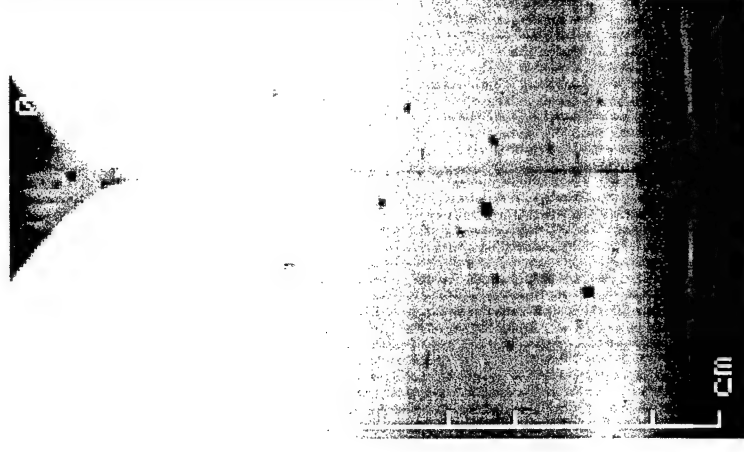




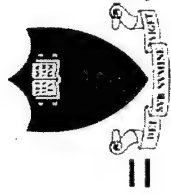
# Cone-Jet Transition for Colloidal Suspension

- *Effect of Particles on*

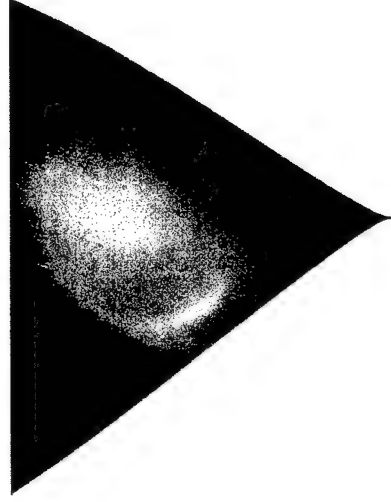
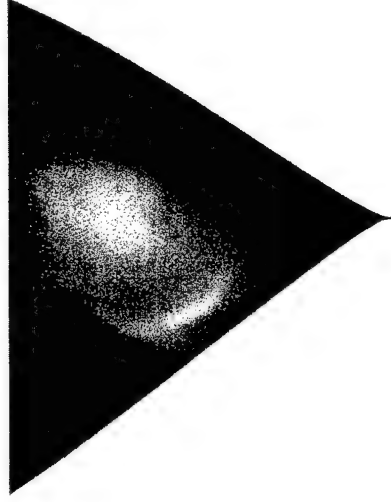
- Cone Jet Transition
  - Scaling Laws
  - Jet Stability
  - Buckling Issues
- *Suspension Investigated*
    - Solvents: water, ethylene glycol, ethanol, glycerol
    - particles: alumina, barium titanate



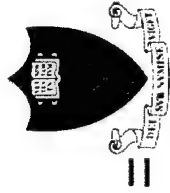
10% Glycerol Dispersed  
Alumina Jet  
Impinging on the surface



# Aqueous Alumina (10 vol% AKP-50)



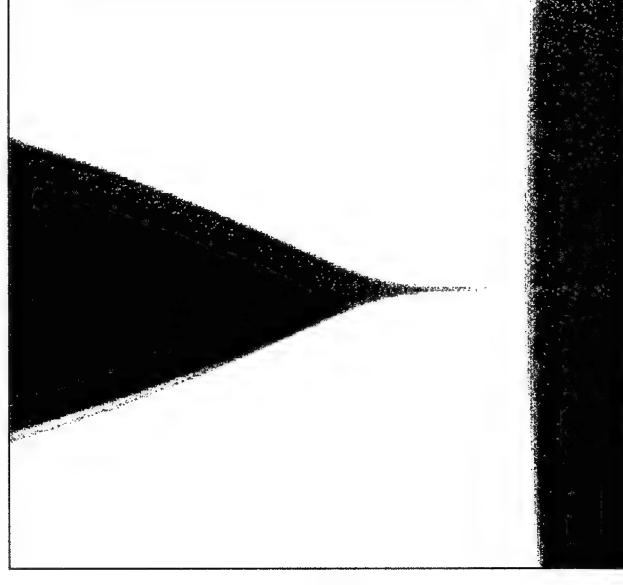
- *Unsteady and Short Jet*
  - Possible Causes:
    - ◆ High conductivity (1.78mS/cm)
    - ◆ Low viscosity



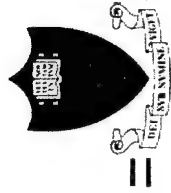
## Effect of Concentration

- *Suspension prepared with water, ethylene glycol and glycerol are limited to low concentrations, typically below 20 vol%.*
- *Higher solid loading usually results in an agglomerated suspension*

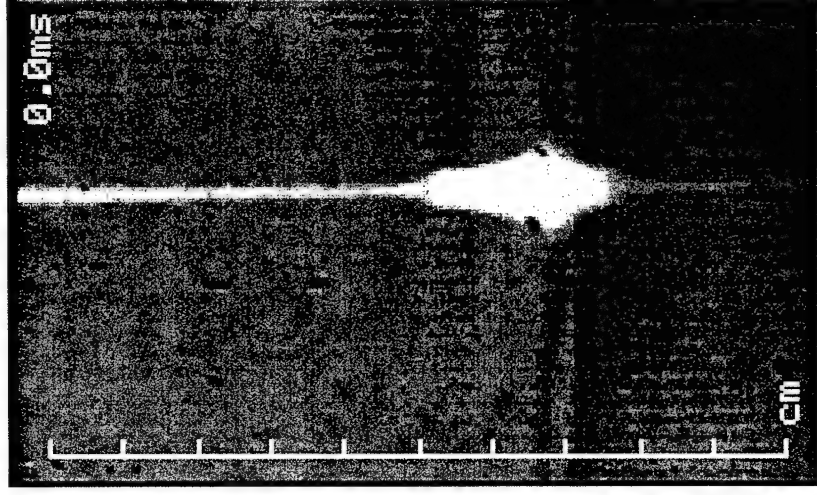
The only stable high loading suspension (up to 40 vol%) prepared thus far is alumina dispersed in ethanol.



Cone-jet transition of a 37.8 vol%  
AKP-50 suspension dispersed in ethanol

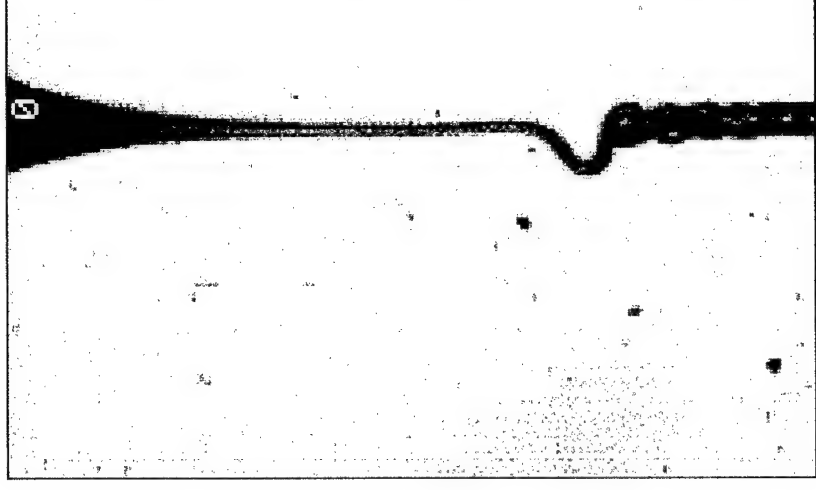


# Buckling Issues



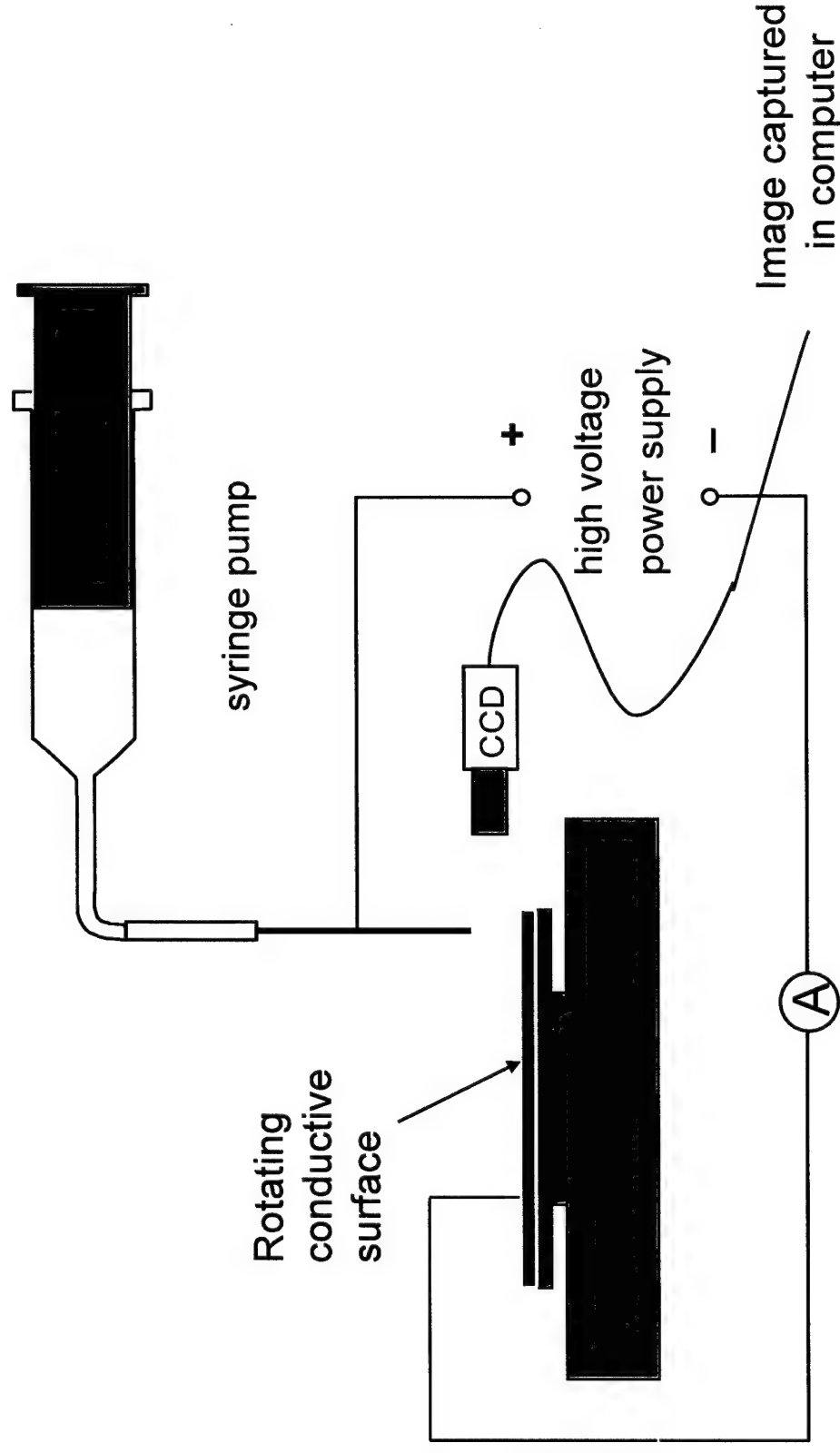
10% Glycerol dispersed  
alumina jet  
impinging on the surface

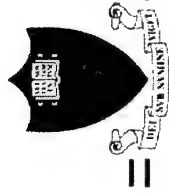
VS.



Honey jet under  
cone-jet domain

# A Simple Writing Device

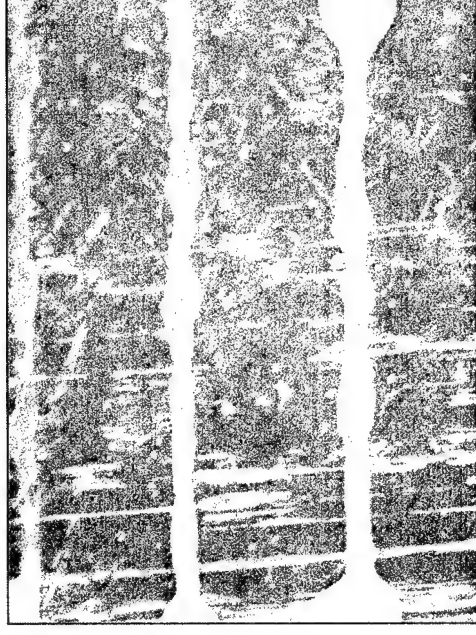




## Line Pattern

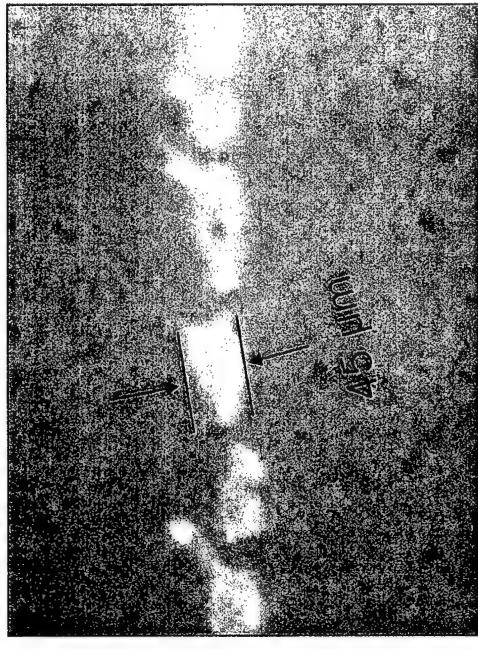
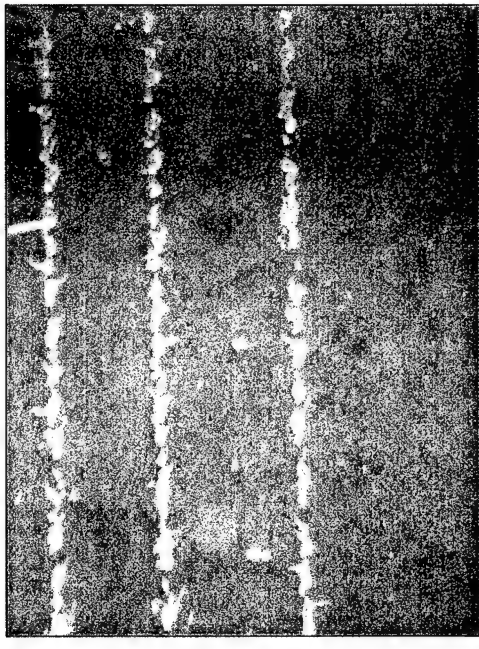
### • *Operating Conditions:*

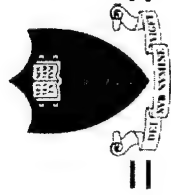
- 10 vol% alumina suspension dispersed in glycerol
- Jet size ~ 10  $\mu\text{m}$
- Flow Rate ~ 2 ml/hr
- Surface velocity ~ 0.2 m/sec
- Substrate surface: 0.1  $\mu\text{m}$  pore size filter membrane
- Cone Base Diameter: 558  $\mu\text{m}$



## Effect of Surface Speed

- *Operating Conditions:*
  - Flow rate ~ 2 ml/hr
  - Surface velocity ~ 0.9 m/sec
  - Substrate surface: 0.1  $\mu\text{m}$  pore size filter membrane
  - Jet size: 10  $\mu\text{m}$
- *Increase in surface moving speed leads reduce line thickness*
- *Rayleigh instability is enlarged at such small scale*

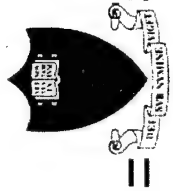




## Conclusions

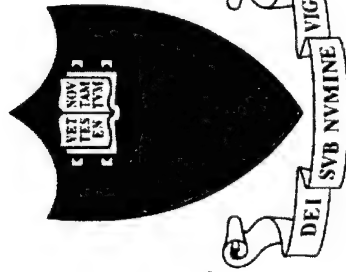
- *Developed simple writing device*
  - *Demonstrated a cone-jet domain for colloidal suspension*
  - *Demonstrated the feasibility of EHD jet printing as a novel patterning technique for both homogeneous solution and colloidal suspension*
  - *Current experiment configuration allowed laying down of continuous 50 - 80 micrometer suspension filament with a large orifice (OD: 558  $\mu\text{m}$ , ID: 300  $\mu\text{m}$ )*
-





## **Future Work**

- *Scale down nozzle to produce micron-size filaments*
  - *Improve writing device design to lay down micron-size filament on a surface*
  - *Match jet speed and the surface speed*
  - *Develop scaling laws for cone-jet transition in colloidal suspensions*
  - *Characterize particle aggregation within the filament*
  - *Surface wetting and dewetting issues*
-

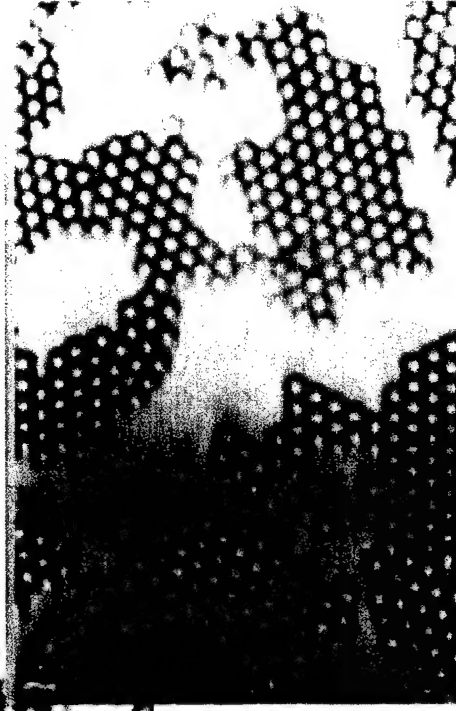
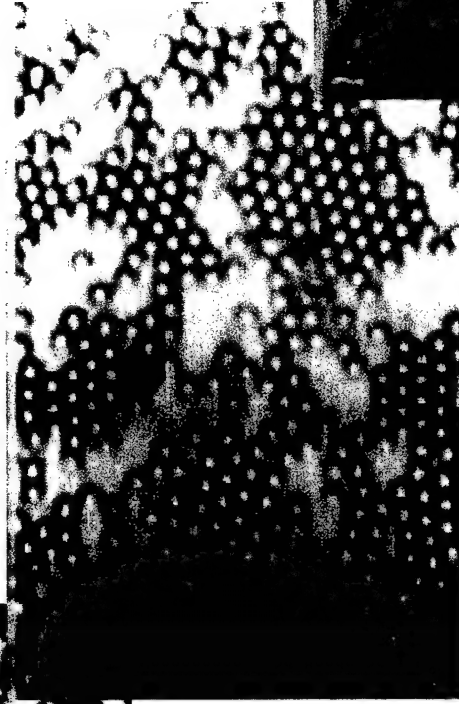
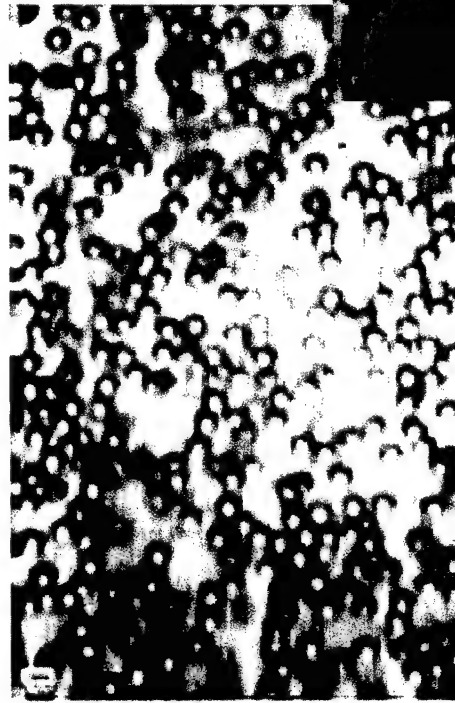
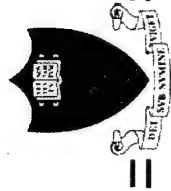


Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

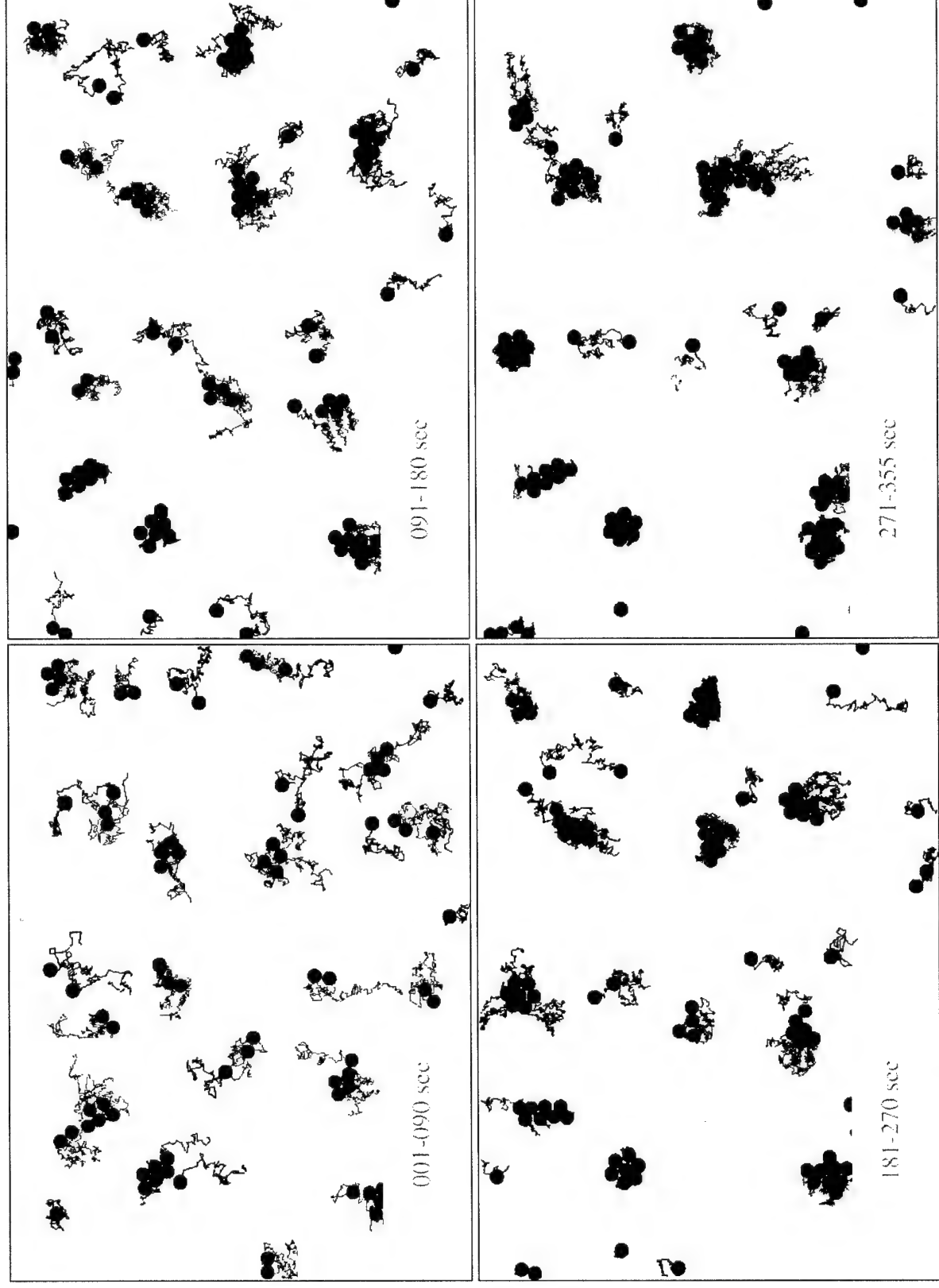
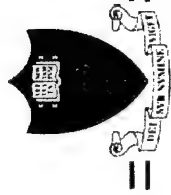
# **Micropatterned Colloidal Crystals: Modulation by UV-light during Electrophoretic Deposition**

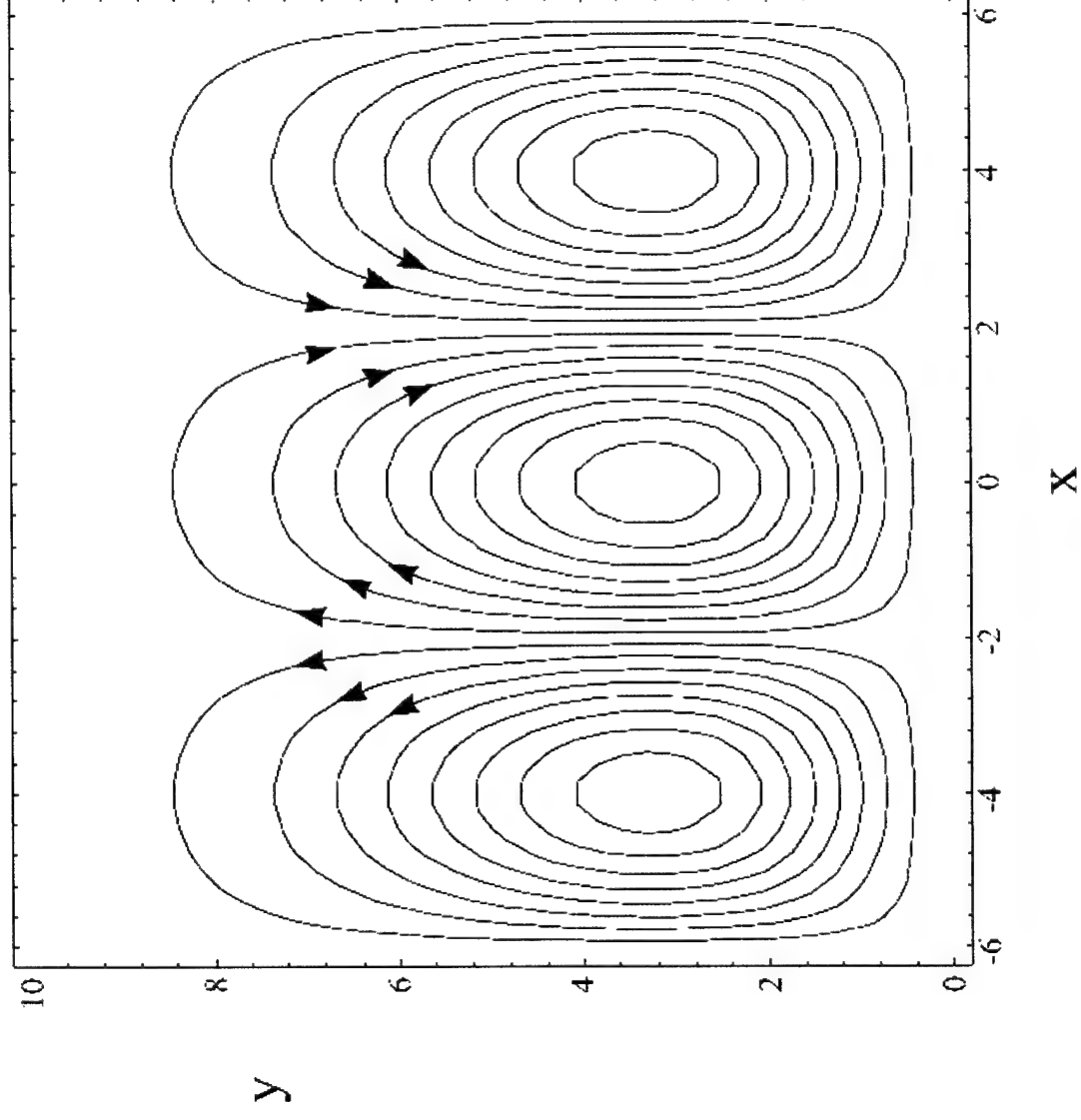
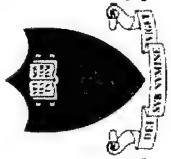
**Ryan C. Hayward, Dudley A. Saville,\* and  
Ilhan A. Aksay**

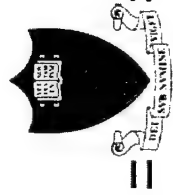
*\*Partial support from the NSF/MRSEC (DMR 94-00362 and DMR 98-09483)*



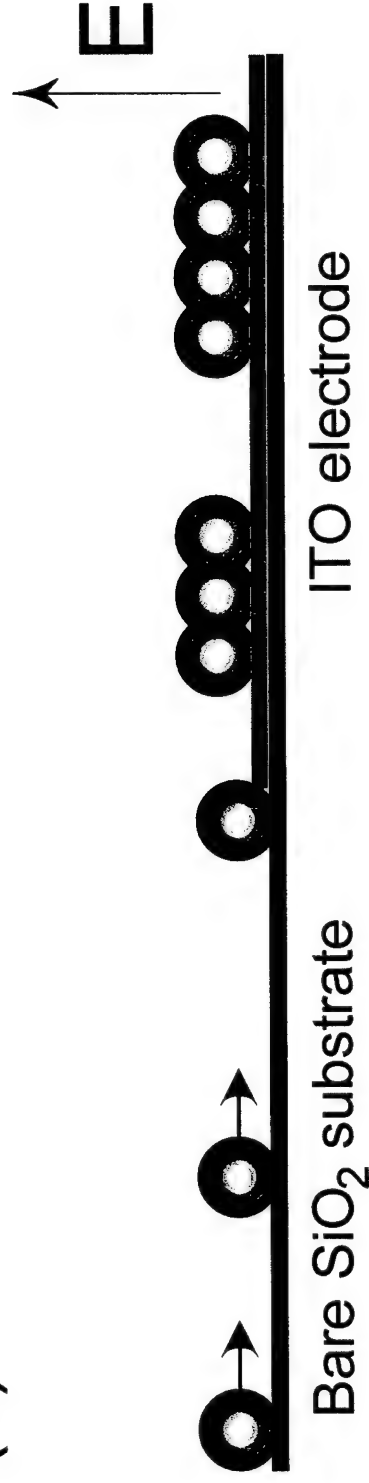
- M Trau, D. A. Saville, and I. A. Aksay, *Science* **272** [5262] 706-09 (1996)
- M. Trau, D. A. Saville, and I. A. Aksay, *Langmuir* **13** [24] 6375-81 (1997)
- Y. Xiao, H. F. Poon, M. Trau, S. Torquato, D. A. Saville, and I. A. Aksay, *Langmuir* (submitted, 1999)



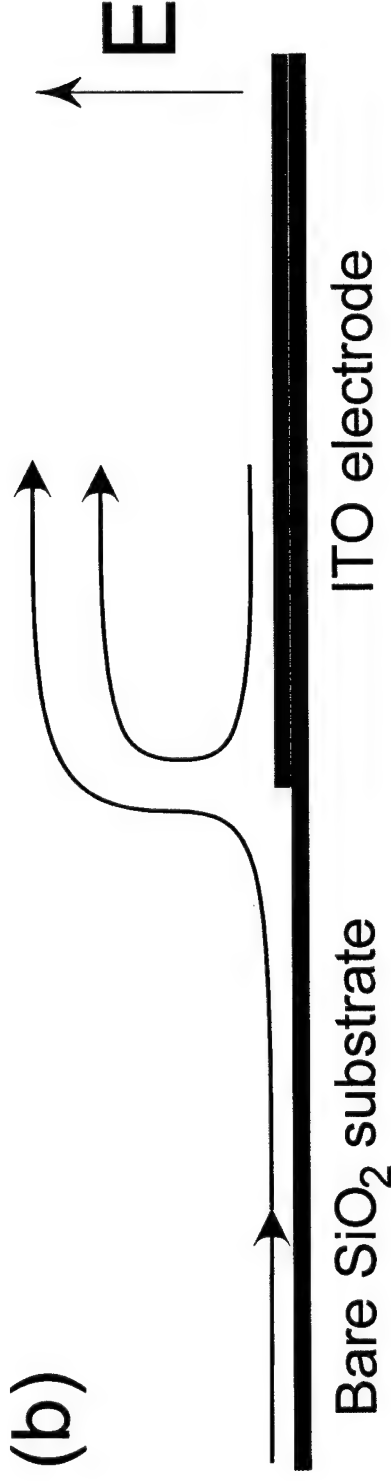




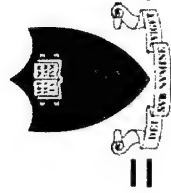
(a)



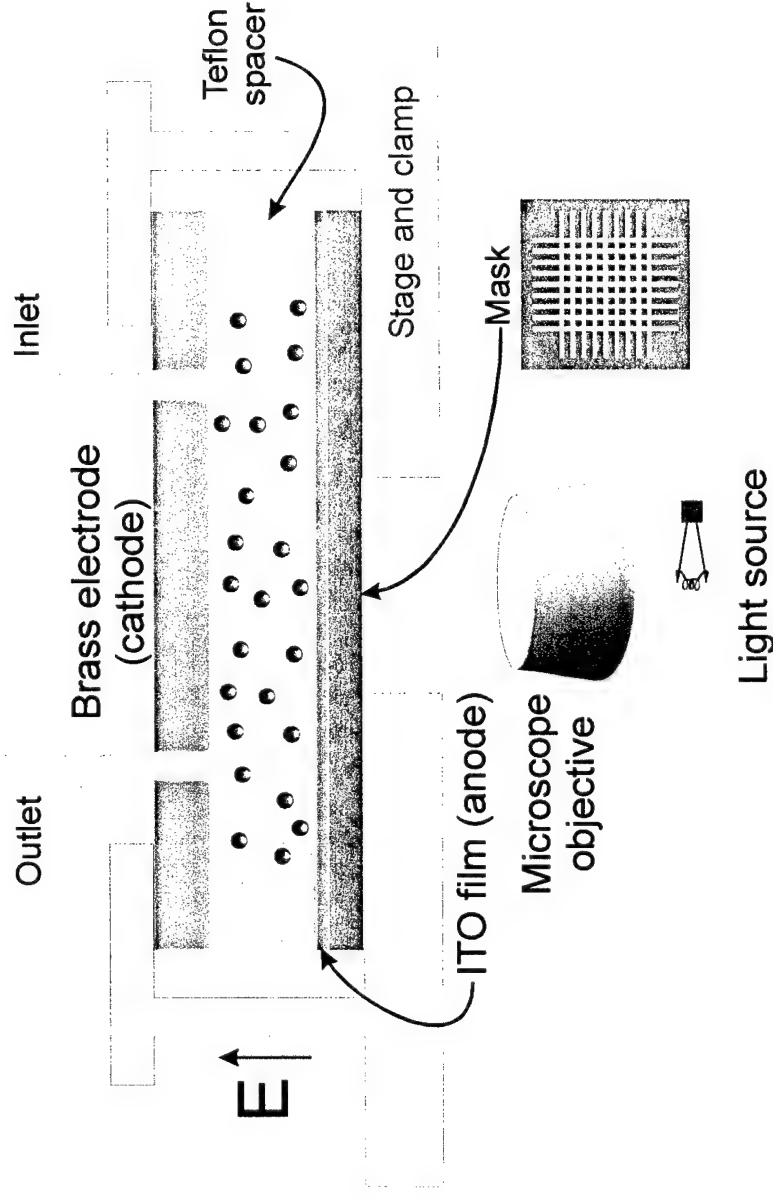
(b)



M. Trau, D. A. Saville, and I. A. Aksay, *Langmuir* **13** [24] 6375-81 (1997)

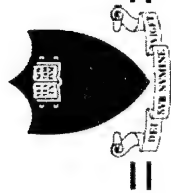


# Light-Modulated Electrophoretic Deposition



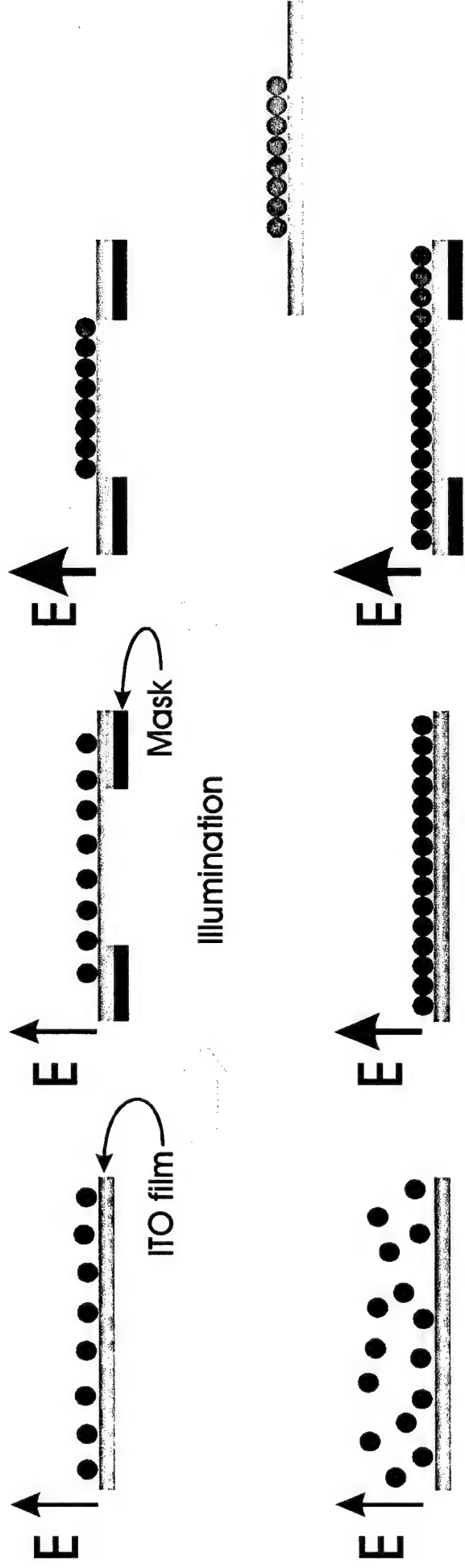
Schematic of apparatus

R. C. Hayward, D. A. Saville, and I. A. Aksay, submitted to *Nature* (1999)



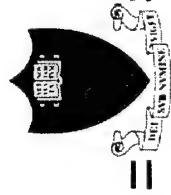
# Pattern Formation

Patterned assembly followed by fixing to substrate



General assembly followed by patterned fixing to substrate





# Patterning of Colloidal Particles



R. C. Hayward, D. A. Saville, and I. A. Aksay, submitted to *Nature* (1999)

# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***The Sponge Phase: Synthesis and Characterization***

**SOL M. GRUNER<sup>‡</sup>, KAREN J. EDLER<sup>‡</sup>, DANIEL M. DABBS<sup>§,#</sup>,  
NAN YAO<sup>#</sup>, AARON RABINOVITCH<sup>‡</sup>, AKIN AKINC<sup>‡</sup>,  
ROBERT K. PRUD'HOMME<sup>§,#</sup>, AND ILHAN A. AKSAY<sup>§,#</sup>**

**DEPARTMENTS OF \*PHYSICS AND §CHEMICAL ENGINEERING, AND  
#PRINCETON MATERIALS INSTITUTE  
PRINCETON UNIVERSITY, PRINCETON, NEW JERSEY 08544**

**<sup>‡</sup>DEPARTMENT OF PHYSICS, CORNELL UNIVERSITY  
ITHACA, NEW YORK**

## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**

# **The “Sponge” Phase**

(and other mesoporous materials)

## **Synthesis and Characterization**

**S. M. Gruner,\* K. J. Edler,\* D. M. Dabbs,†  
E. Hutchins,\* K. M. McGrath,† and I. A. Aksay†**

**\*Physics, Cornell University,  
Ithaca, New York 14850**

**†Chemical Engineering and §Princeton Materials Institute,  
Princeton University, Princeton, New Jersey 08540**

**†Chemistry, University of Otago,  
New Zealand**

**Collaborators: L. Fetters, P. Wright, C. Ober, and X. Li**

*Supported by ARO/MURI under grant DAAH04-95-1-0102*

## **Ideally Mesoporous Materials**

- *Contain well-defined three-dimensional network of pores*
- *Self-assemble via hydrophilic-hydrophobic interactions of the constituents, with possible subsequent processing which preserves form*
- *Have pore dimensions and structure which can be varied at will during synthesis*
- *Allow further formation of composites for applications*

## **Goals**

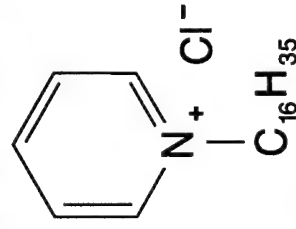
- *To understand mesoporous materials formation and properties, including materials to vary:*
  1. Chemical properties
  2. Physical properties
  3. Degree to which part of the structure can be removed
  4. Synthesis pathways

## Potential Applications

- *Low index optical and electronic materials*
- *Filtration media*
- *Nano-composites*
- *Encapsulation of proteins and macromolecules*
- *Catalysts and catalyst supports*
- *Osmotic membranes*
- *Selective liquid barriers*
- *Super-capacitors*
- *Heavy metal and pollutant sponges*
- *Insulation*
- *...*

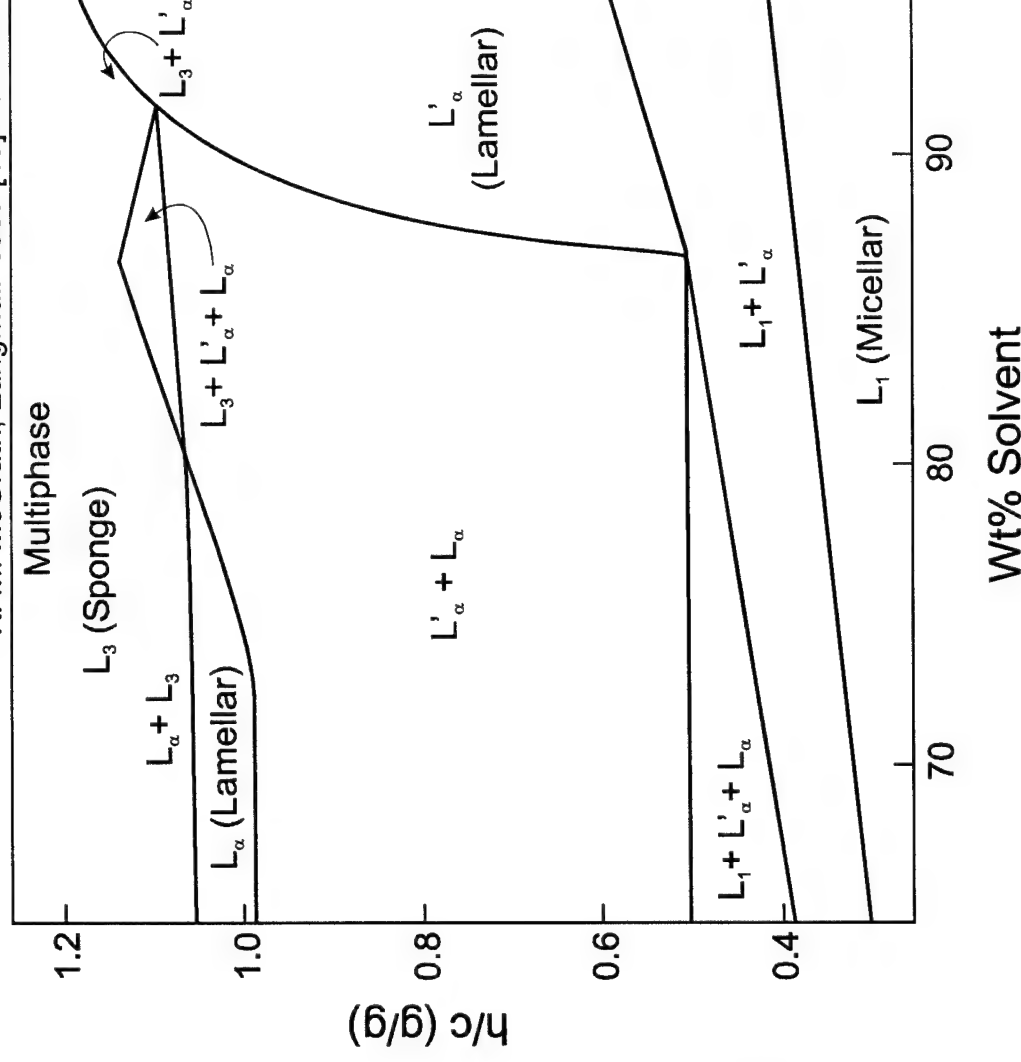
## $L_3$ Phase

- Cationic surfactant:  
cetylpyridinium chloride  
(CpCl)

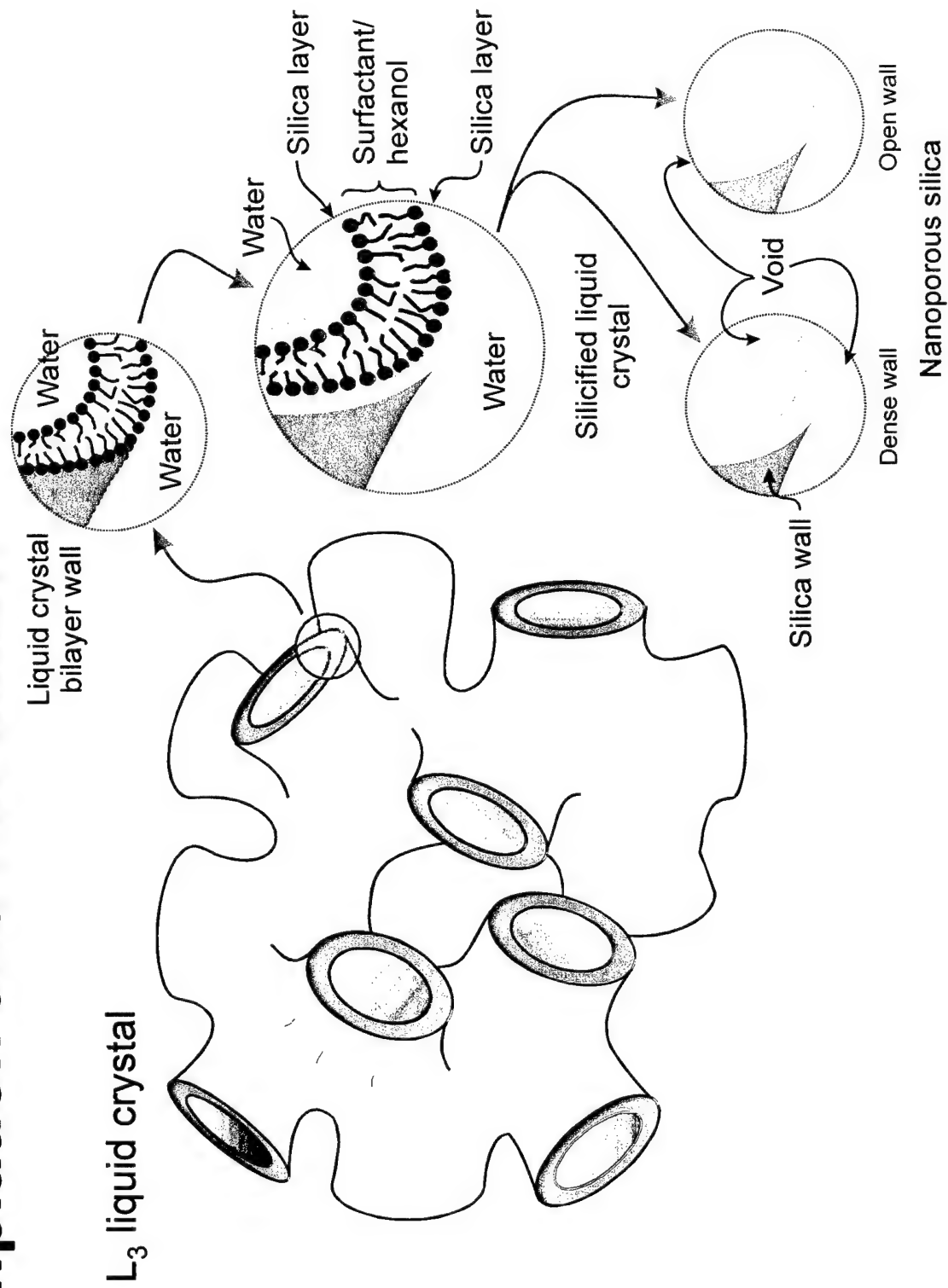


- Cosurfactant: hexanol  
( $C_6H_{13}OH$ )
- Solvent (aq. HCl) ranges  
from 55 to 95% by weight
  - ◆ yields pores of 5 to 100 nm, scaled to solvent content

K. M. McGrath, *Langmuir* 1997 [13] 1987-95

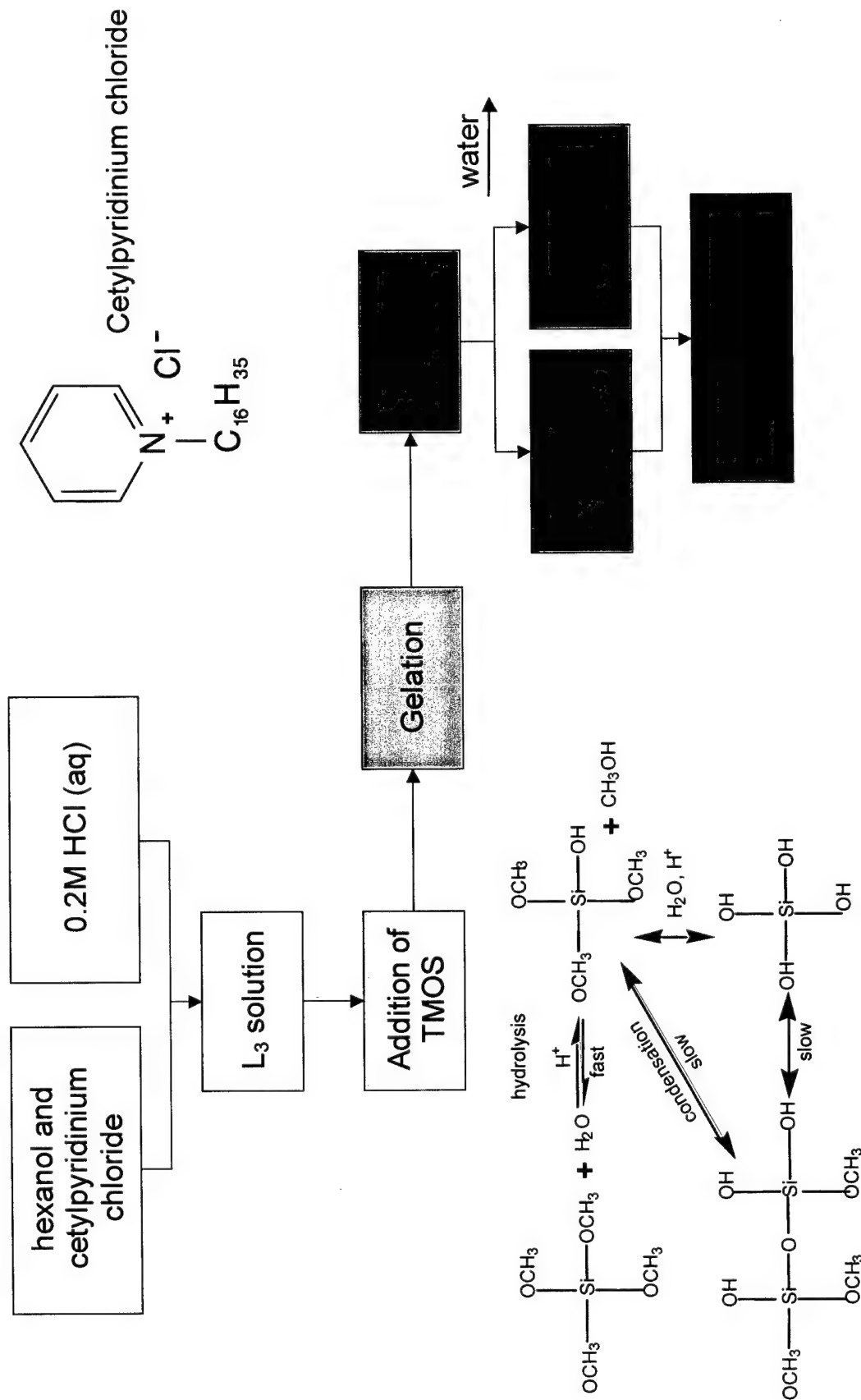


# Templation and Extraction



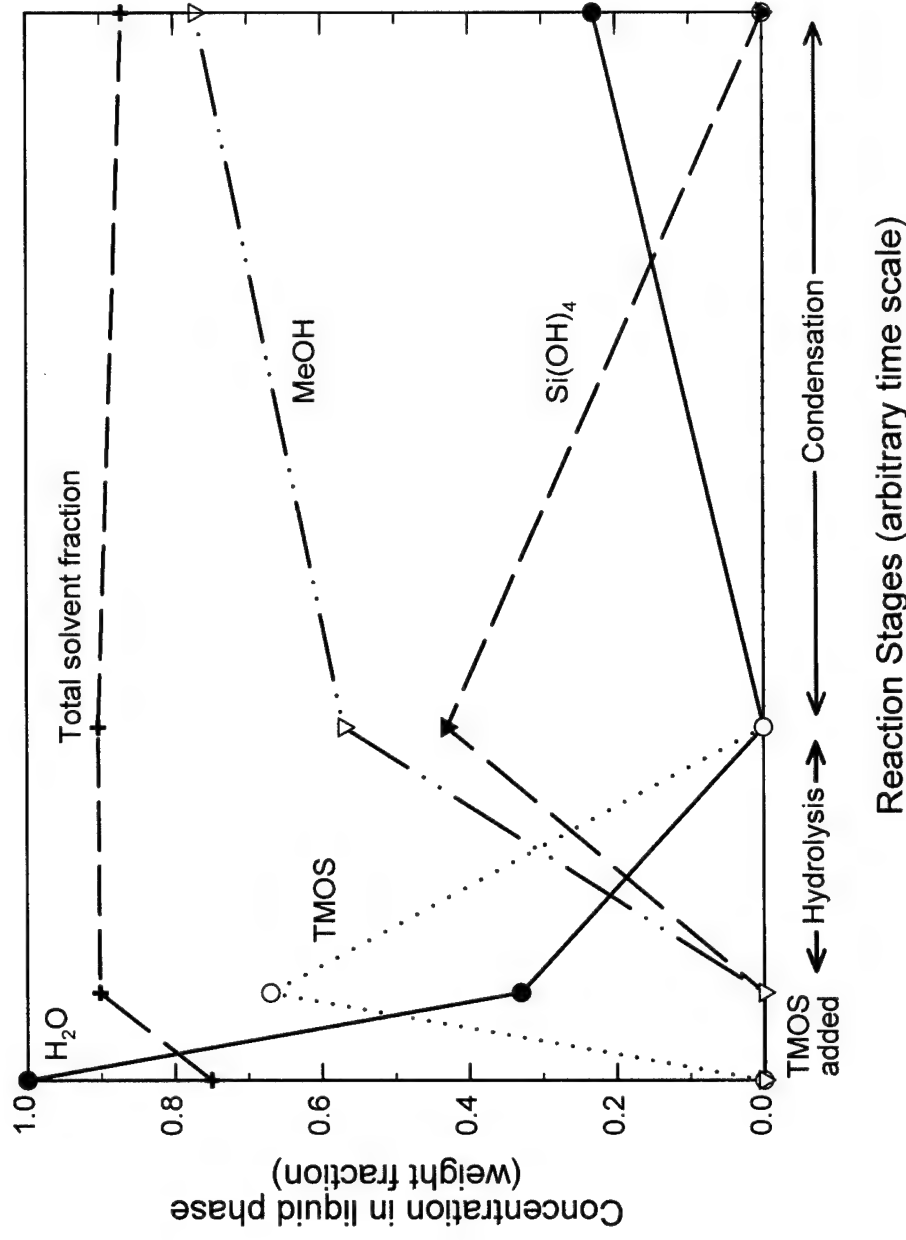


# Procedure



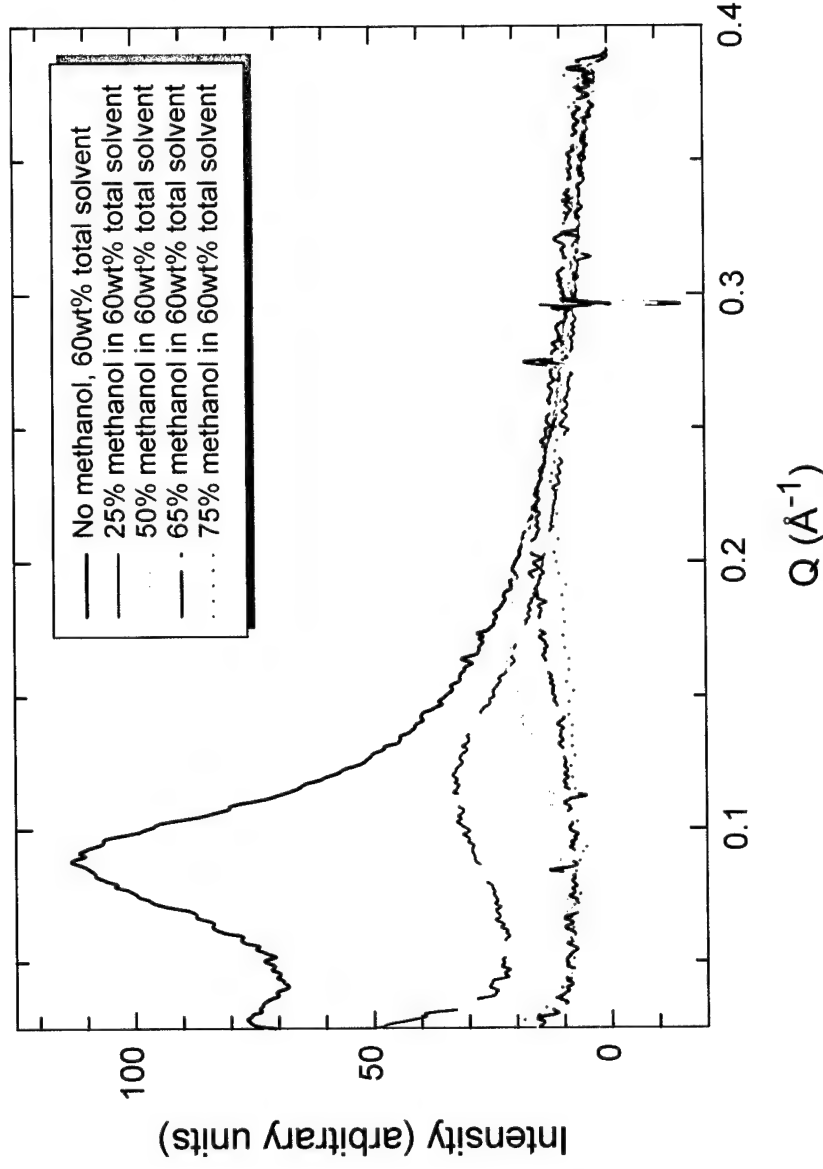
# Changes in the Liquid Phase during Templating

- Adding TMOS raises solvent fraction in  $L_3$  solution
- Hydrolysis removes water, adds methanol to the liquid phase
- Condensation returns water to liquid phase
- Final effective solvent fraction greater than initial



## Effect of Methanol on L<sub>3</sub> Liquid Crystal

- Hydrolysis of TMOS produces methanol
- Increasing methanol content in solution roughens surface of bilayer and expands bilayer surface area
- Competing processes:
  - ◆ dissolution of liquid crystal
  - ◆ condensation of TMOS on surfaces



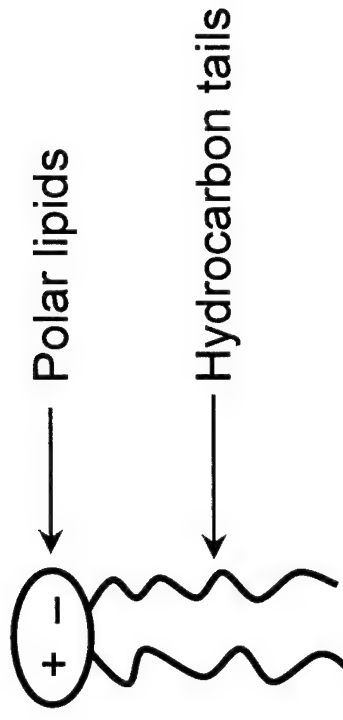
## Generalized Amphiphile



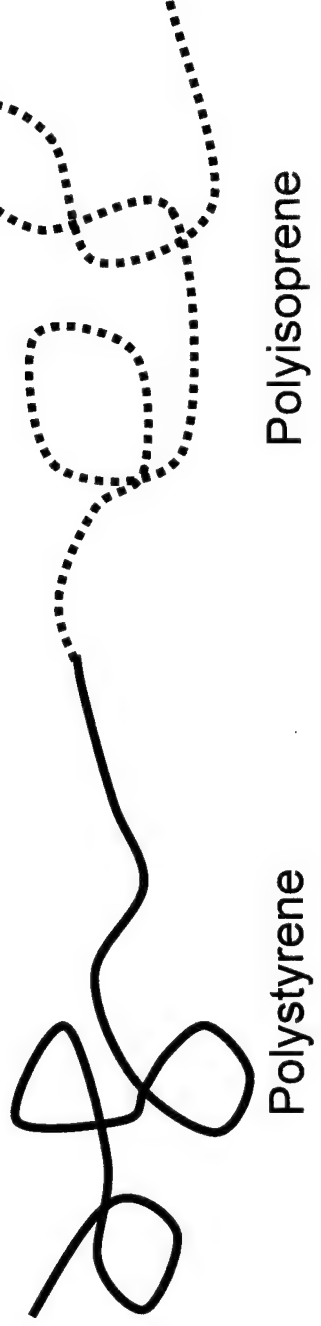
Where A & B do not mix

- **Surfactants**

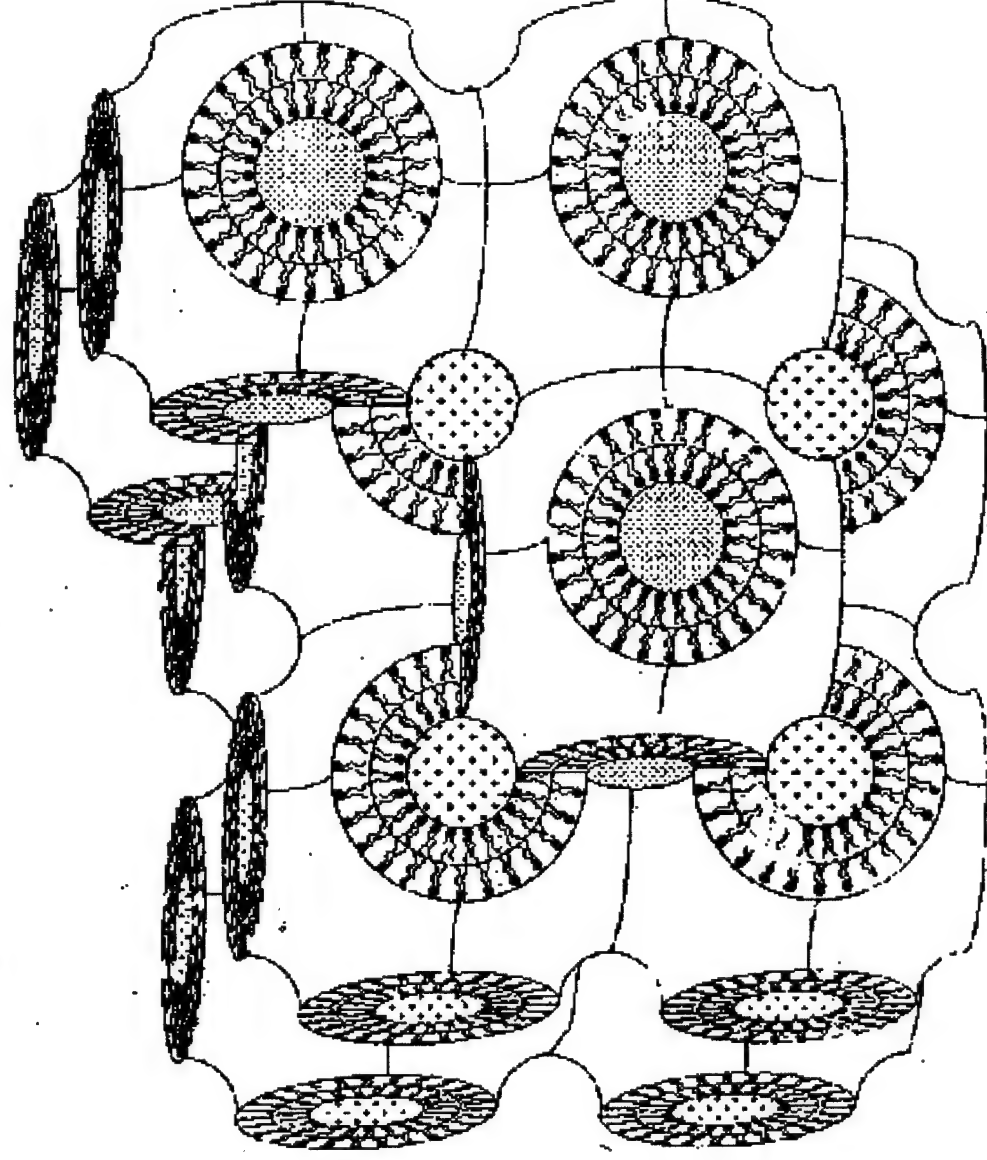
- Detergents
- Soaps
- Biomembrane lipids



- **Block copolymers**

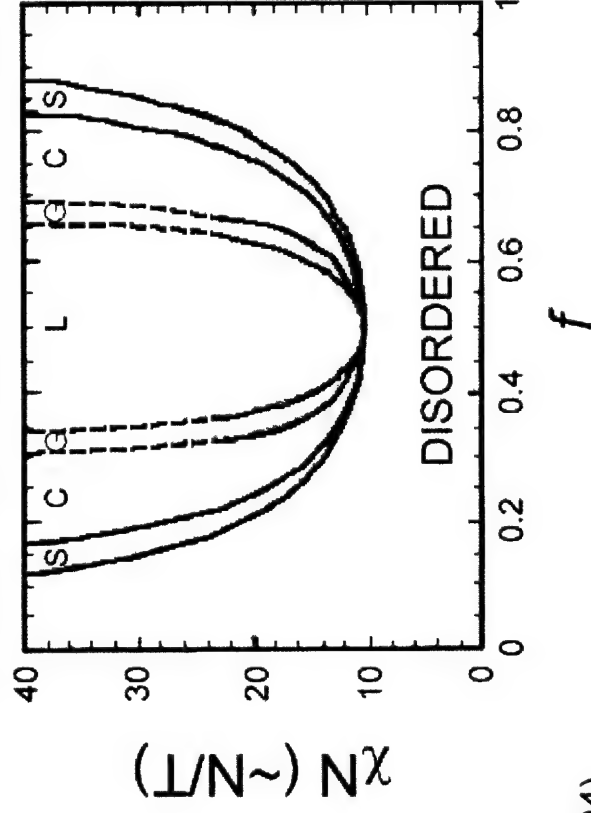
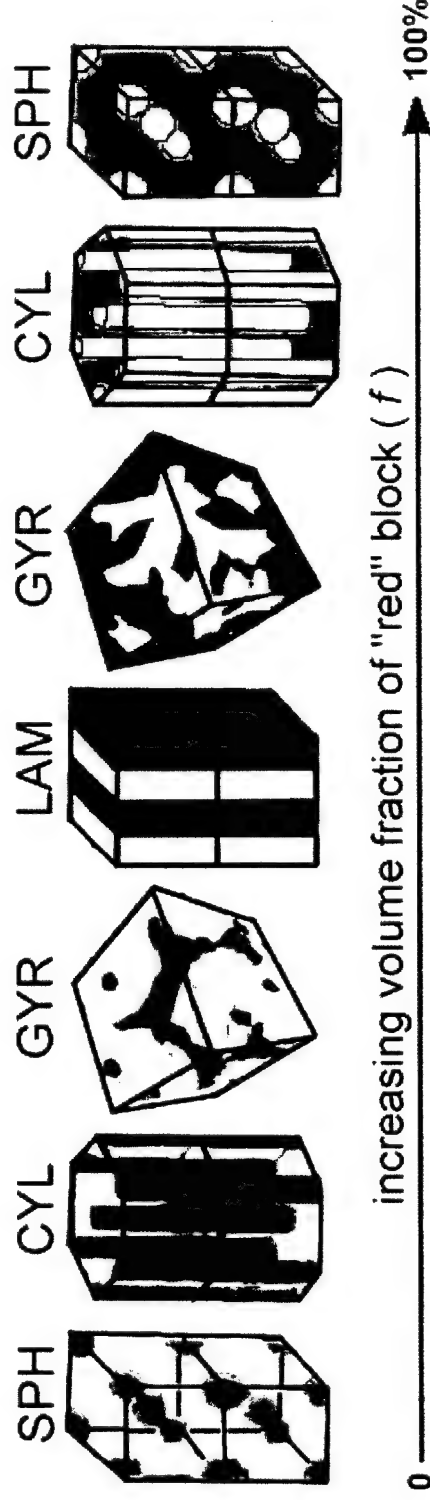


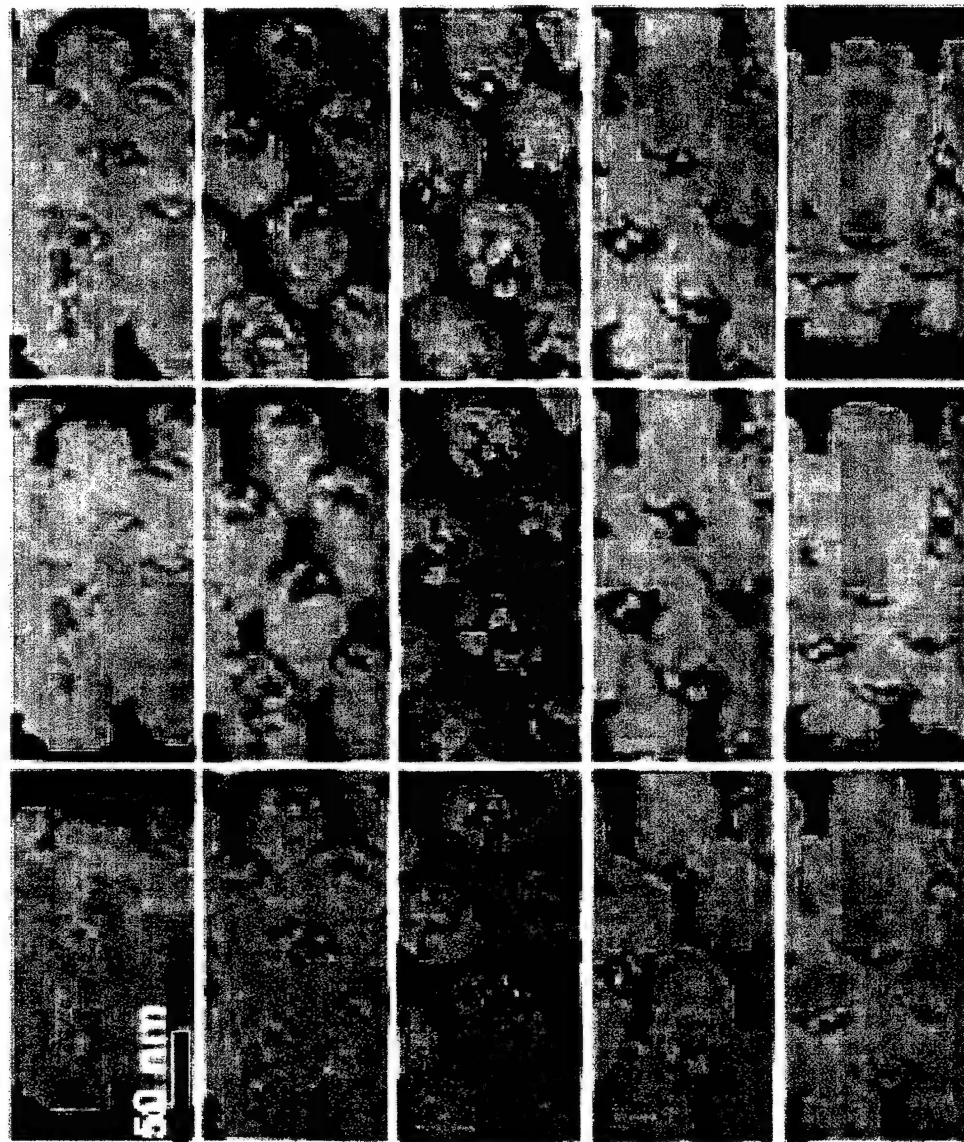
## Plumber's Nightmare (Ia3d)



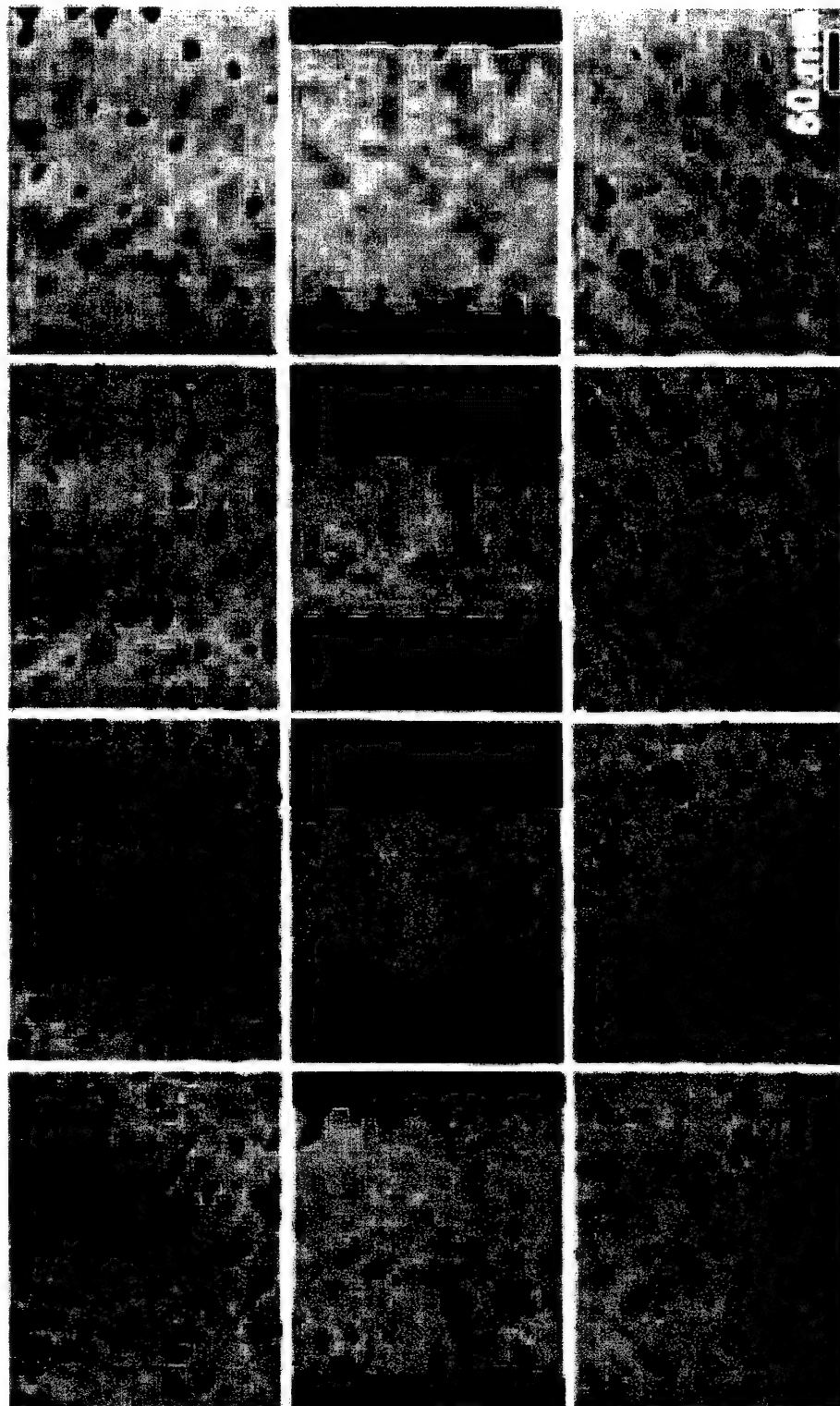
Tate et al., *Chem. Phys. Lipids* **57** (1991) 147

# Block Copolymer Phase Behavior





Tomograph of cylinder phase of copolymer blend; 10° rotations.  
Spontak *et al.*, *Macromol.* **29** (1996) 4496



Tomograph of gyroid phase of copolymer blend; 20° rotations.  
Spontak *et al.*, *Macromol.* **29** (1996) 4496



## Microphase Separation

- *Repulsion between incompatible polymer segments*

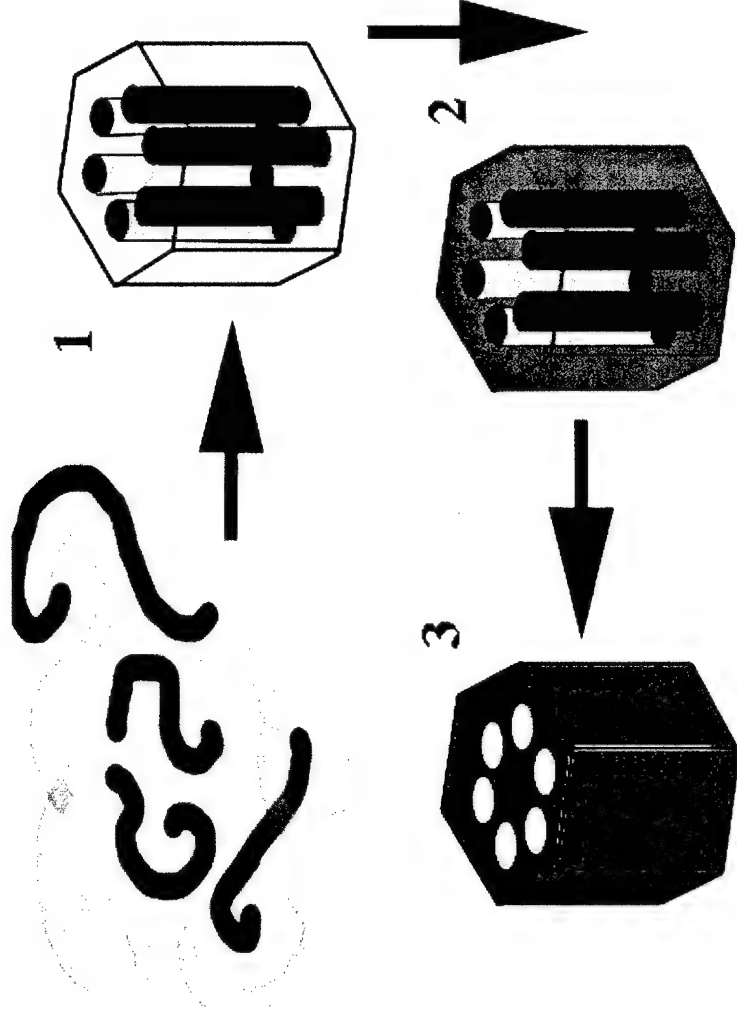
$$\varepsilon_{ij} = - \sum \frac{3}{4} \frac{I_i I_j}{I_i + I_j} \frac{\alpha_i \alpha_j}{r_{ij}^6}$$

$$\chi = \frac{1}{kT} \left[ \varepsilon_{AB} - \frac{1}{2} (\varepsilon_{AA} - \varepsilon_{BB}) \right]$$

- *Condition for microphase separation:  $\chi N > 10$* 
  - $\chi N$  controls segregation
  - $N_A/N_B$  controls phase structure

## Strategy

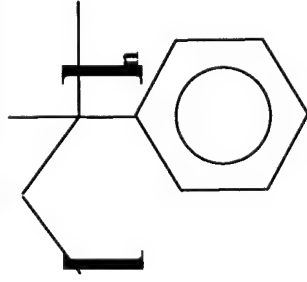
- *Synthesize cylinder phase diblock copolymer (A:B = 1/3)*
- *Make A segment labile*
- *Cross-link B segment*
- *Cross-link, degrade and remove A, characterize by x-ray and EM*



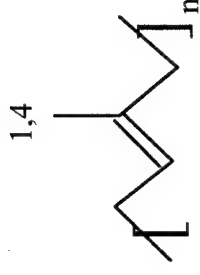
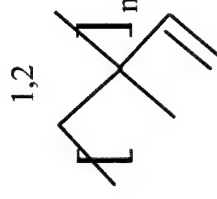
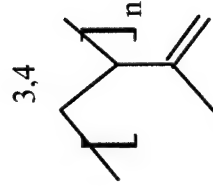
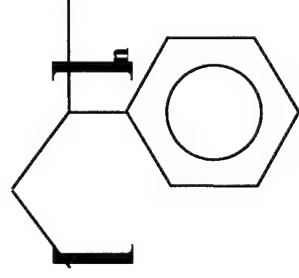
## Microphase Separation

- *Our polymer:*  
*poly( $\alpha$ -methylstyrene)-b-poly(isoprene) diblock copolymer*
  - 1:3 ratio by weight
  - Hexagonal (cylindrical) microstructure

Poly( $\alpha$ -methylstyrene)



Poly(styrene)



Three isomers of poly(isoprene)

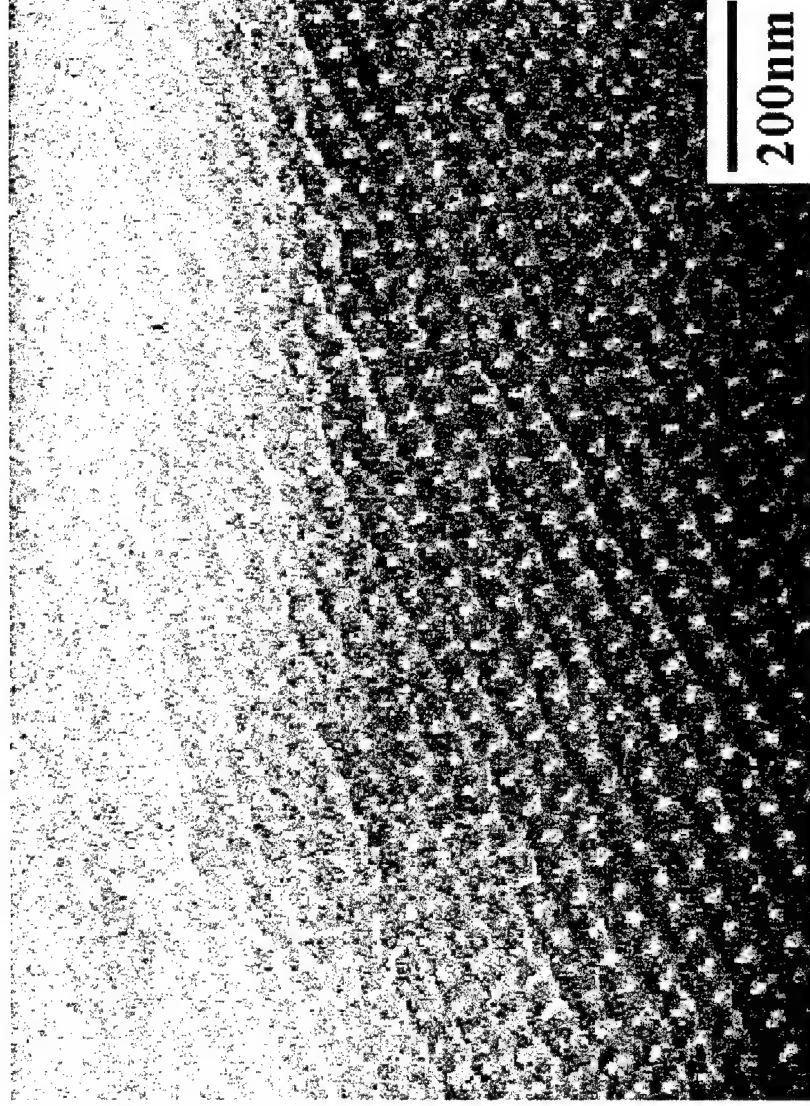
## **Experimental Procedure**

- 1. Synthesize**
- 2. Solvent cast from toluene onto teflon**
- 3. UV cross-link**
- 4. Heat under vacuum to degrade, remove  $\alpha$ -methyl styrene**
- 5. Characterize**

## Results

- *Microstructure visible in TEM*

■ Pores!!!



Positive image

## **Next Steps**

- 1. Synthesize other polymers to move into bicontinuous region***
- 2. Explore other polymers chemistries***
- 3. Back-fill cross-linked polymer host with organic and inorganic guest molecules, for different properties***

# **SMART MATERIALS SYSTEMS THROUGH MESOSCALE PATTERNING**

## ***The Sponge Phase: Applications***

**DANIEL M. DABBS<sup>§,#</sup>, SOL M. GRUNER<sup>‡</sup>, KAREN J. EDLER<sup>‡</sup>,  
NAN YAO<sup>#</sup>, AARON RABINOVITCH<sup>‡</sup>, AKIN AKINC<sup>‡</sup>,  
ROBERT K. PRUD'HOMME<sup>§,#</sup>, AND ILHAN A. AKSAY<sup>§,#</sup>**

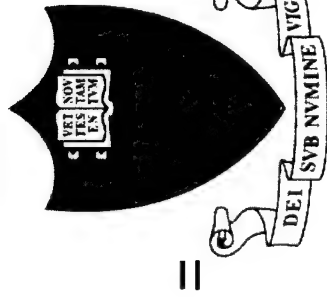
**DEPARTMENTS OF \*PHYSICS AND §CHEMICAL ENGINEERING, AND  
#PRINCETON MATERIALS INSTITUTE  
PRINCETON UNIVERSITY, PRINCETON, NEW JERSEY 08544**

**‡DEPARTMENT OF PHYSICS, CORNELL UNIVERSITY  
ITHACA, NEW YORK**

## **FIFTH ARO/MURI PROGRAM REVIEW**

**HARVARD UNIVERSITY  
CAMBRIDGE, MASSACHUSETTS**

**SEPTEMBER 28 - 29, 1999**



Department of Chemical Engineering and  
Princeton Materials Institute  
Princeton University

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# **L<sub>3</sub> “Sponge” Phase: Applications**

**Daniel M. Dabbs,\*§ Karen J. Edler,‡ Kate M. McGrath,†  
Nan Yao,§ Sol M. Gruner,‡ and Ilhan A. Aksay\*§**

**\*Chemical Engineering and §Princeton Materials Institute,  
Princeton University, Princeton, New Jersey 08540**

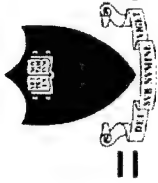
**‡Physics, Cornell University,  
Ithaca, New York 14850**

**†Chemistry, University of Otago,  
New Zealand**

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*Supported by ARO/MURI under grant DAAH04-95-1-0102*





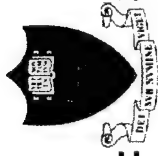
# The Sponge Phase–Applications

## • *Objectives*

- Develop mesostructured cellular ceramics for use in specific applications, involving
  - ◆ monoliths for matrix support
  - ◆ coatings and thin films

## • *Approaches*

- Retention of mesostructure during and after templation
  - Efficient extraction of organic component
  - Silicate as a passivating coating and support matrix
  - Eventual templating using other metalloorganic systems
-



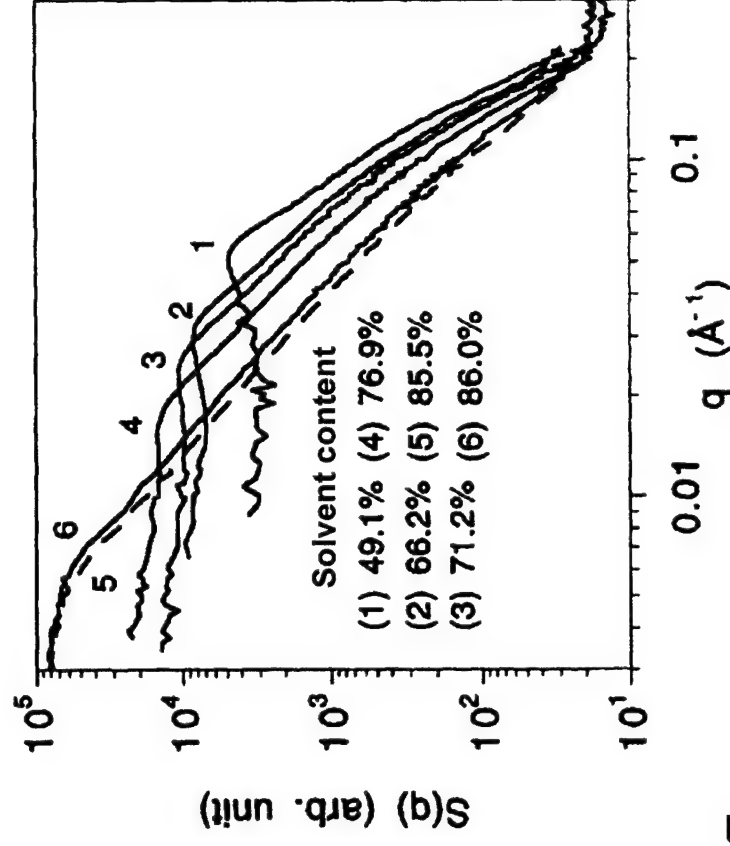
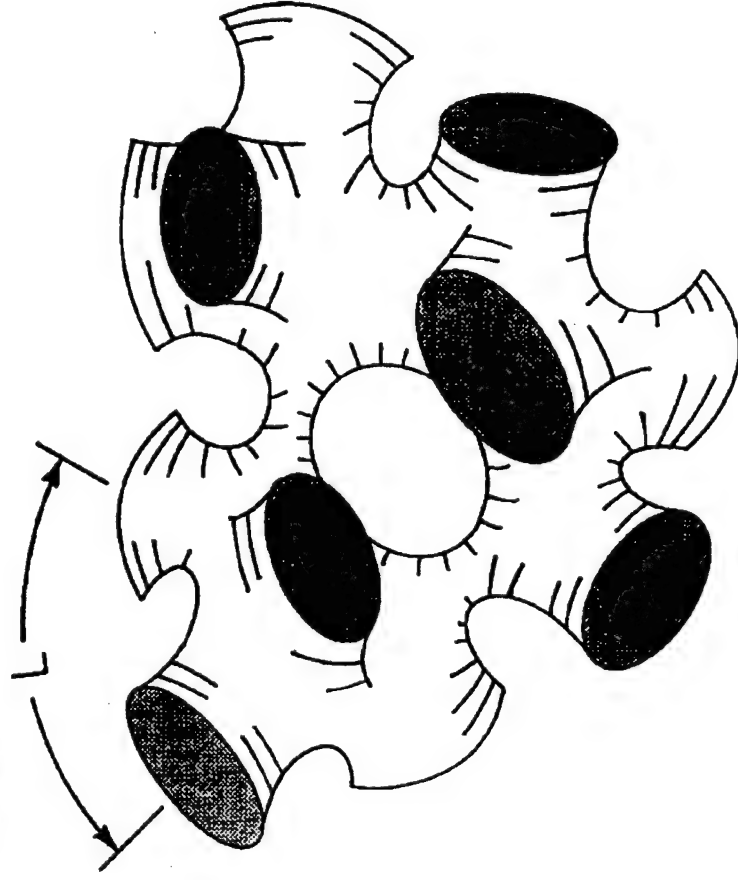
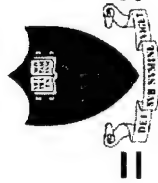
## **L<sub>3</sub>-Templated Silicates**

- *Silica deposition on isotropic L<sub>3</sub> phase yields high surface volume with contiguous, uniform pore structure*
- *Materials can be supercritically extracted to remove template (N. Mulders, University of Delaware) resulting in optically transparent media*
- *Application development*
  - **Holographic storage medium (H. Katz, Lucent Technologies)\*:**
    - ◆ High permeability to monomeric precursors
    - ◆ *In-situ* reaction and curing to form photoactive matrix
    - ◆ Two-photon read-and-write through transparent composite
  - **Thin films and coatings**

*\*Postdoctoral researcher support provided for two years (\$100,000)*

D. M. Dabbs, S. M. Gruner, H. Katz, N. Mulders, and I. A. Aksay

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$$L = \frac{2\pi}{q_c}$$

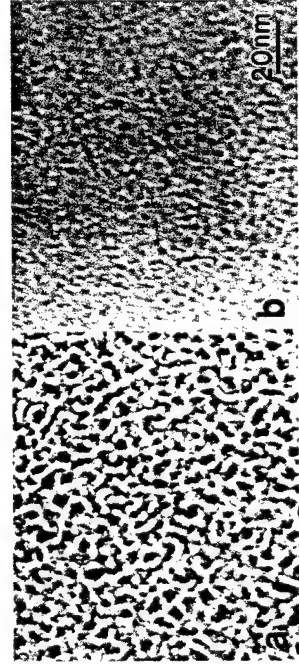
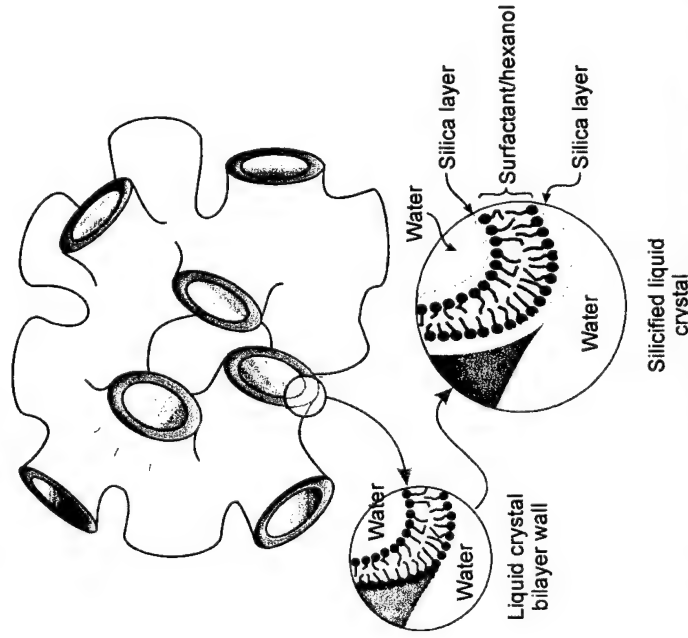
G. Porte et al., *J. Phys. (France)* **49** (1988)

Lei et al., *Phys. Rev. E* **56** [1] (1997)

- Flexible, sponge-like liquid crystal composed of surfactant bilayers separating primary volume into 2 bicontinuous volumes
- 5 nm - 1  $\mu\text{m}$  cell lengths ( $L$ ) inversely related to  $q$  vector ( $q = 4\pi\sin\theta/1.54 \text{ \AA}$ )
- "Dilution effect:" increasing solvent content expands cell length

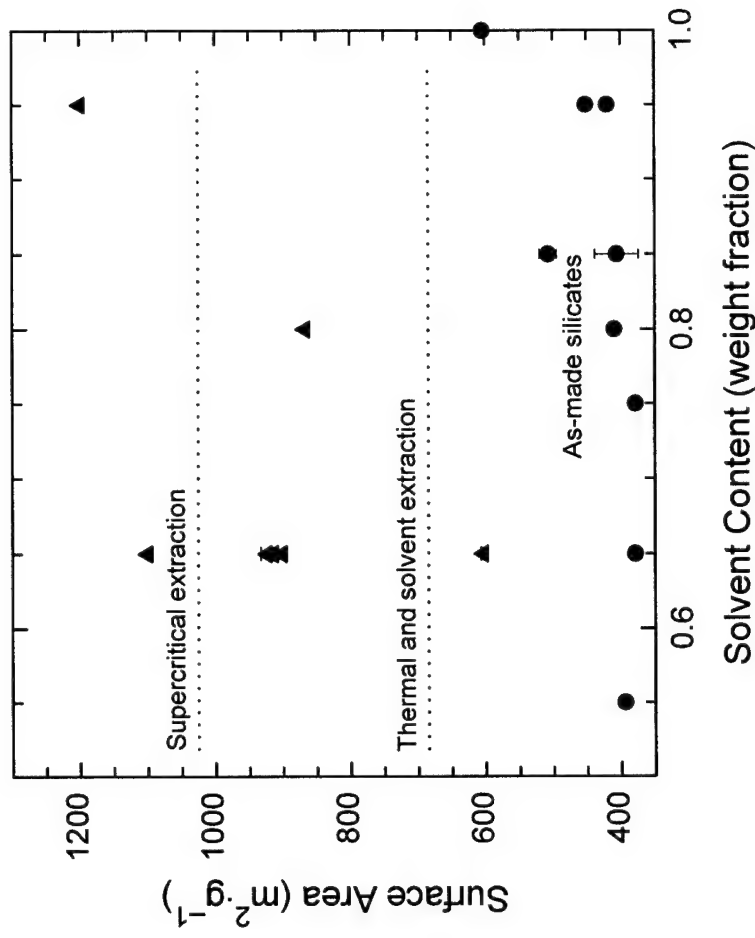


## Past Studies



$L_3$  silicate, dried

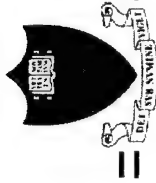
Silica xerogel



K. M. McGrath, D. M. Dabbs, N. Yao, I. A. Aksay, and S. M. Gruner, *Science* **277** 552-6 (1997)

K. M. McGrath, D. M. Dabbs, K. J. Edler, N. Yao, I. A. Aksay, and S. M. Gruner, *Langmuir* (in press, 1999)

K. M. McGrath, D. M. Dabbs, I. A. Aksay, S. M. Gruner, U.S. Provisional Patent Application Serial#60/047,463; Docket No. 97-1407-1 (1997)



## Comparative Properties of SCE-L<sub>3</sub> Silicates

### • SCE-L<sub>3</sub> Silicates

- Density:  
~0.25 g/cm<sup>3</sup>
- Surface Area:  
400-1200 m<sup>2</sup>/g
- Pore size:  
narrow distribution,  
controlled diameter  
(5 nm to 100 nm)

### • Aerogels

- Density:  
0.7-0.001 g/cm<sup>3</sup>
  - Surface Area:  
400-1000 m<sup>2</sup>/g
  - Pore size distribution:  
<2nm “micropores”,  
2-50nm “mesopores”,  
>50 nm “macropores”
-



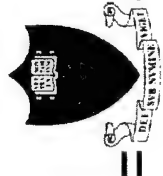
## **Applications**

### **• *Current studies***

- Low index optical material
- Ultracapacitors
- Heavy metal and pollutant scrubbers
- Thin films and monoliths for sensors and optoelectronics
- Catalysts and catalyst supports

### **• *Potential applications***

- Selective liquid barriers
  - Osmotic membranes
  - Energy storage
  - Controlled filtration
  - Insulation
  - Nanocomposites
  - Encapsulation of proteins and macromolecules
-

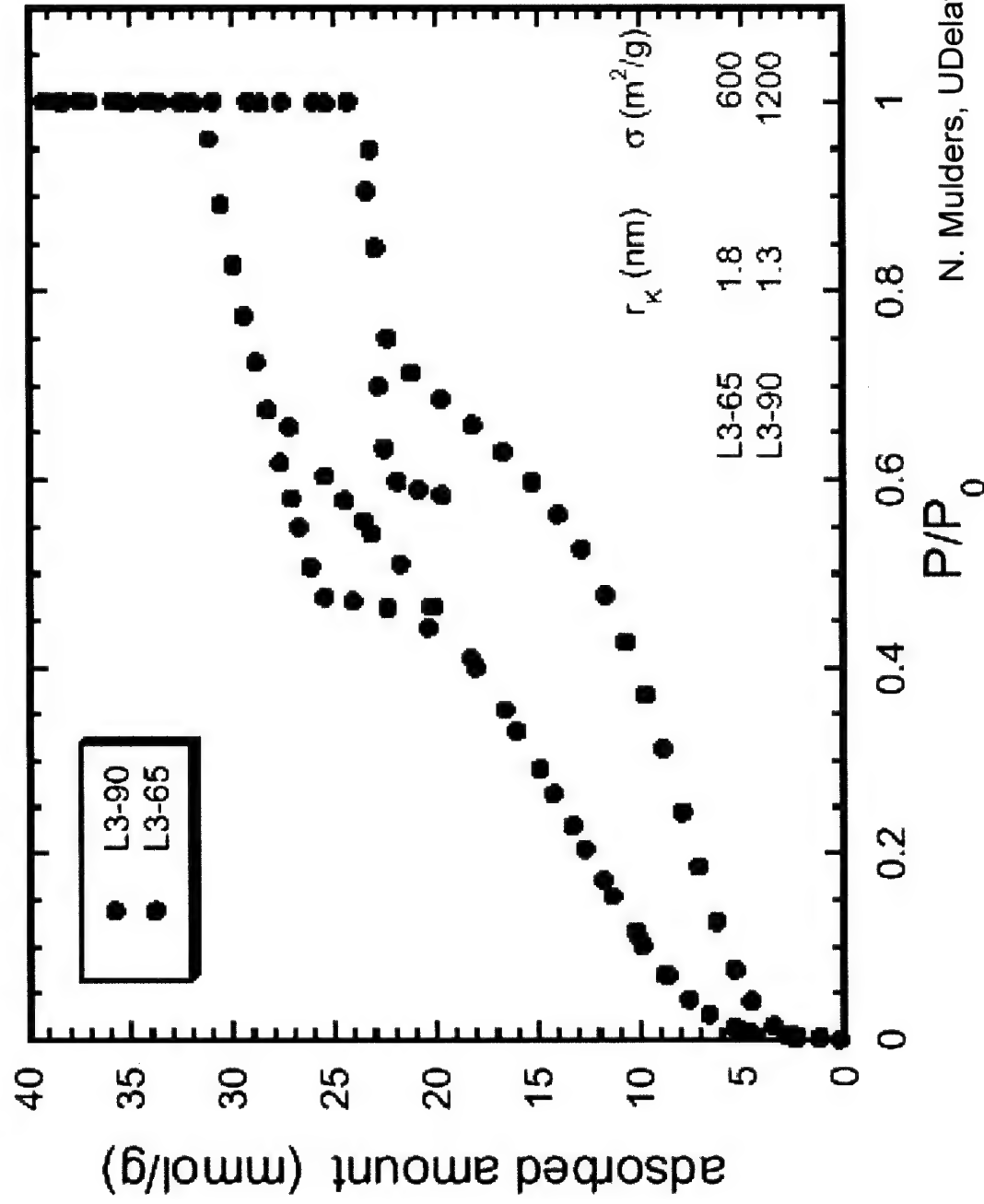


# Applications of the $L_3$ Phase: Current Studies

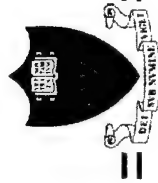
- ***Supercritical Extraction***
  - ***Monoliths***
    - Composite structures
      - ◆ Cellular matrix composites
    - Holographic imaging (Lucent Technologies)
    - Ultracapacitors
      - ◆ Metallization via electroless deposition
  - ***Thin films***
    - Passivating layers (low  $k$  dielectric materials)
      - ◆ PZT microcantilevers
    - Active sensors
-



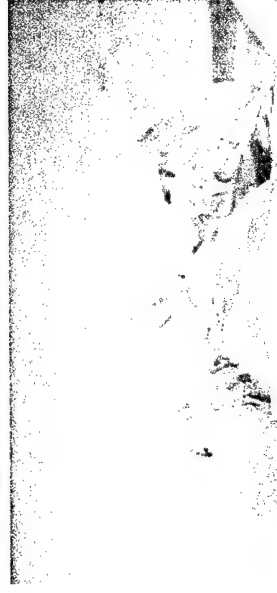
# Supercritical Extraction



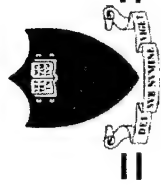




## Monoliths

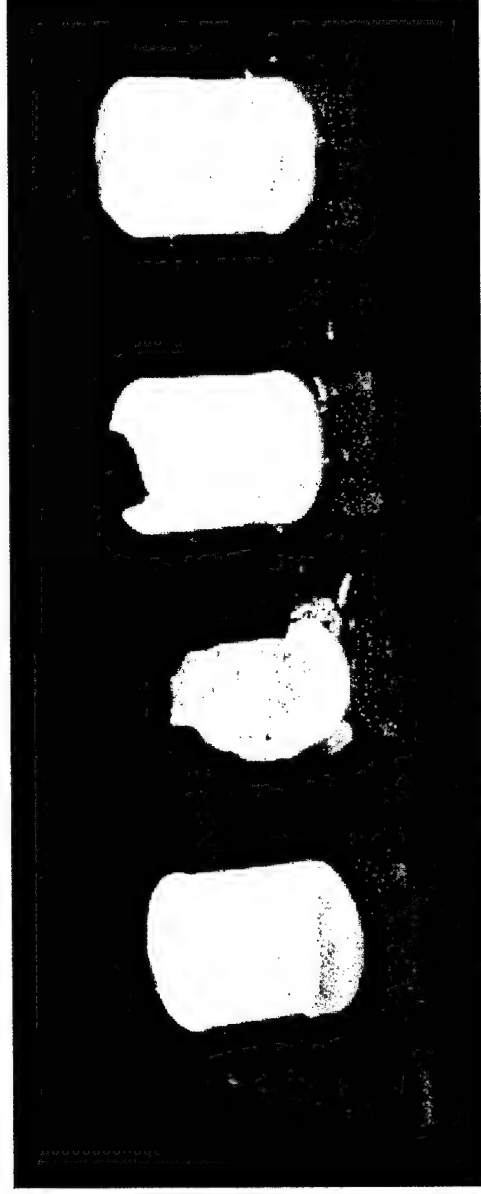


- ***As cast, slow dried in sealed container***
  - Shrinkage up to 20-30% (by volume )
  - Low strength
  - Highly sensitive to air
  - Very long processing times (>3 months)
- ***Supercritical extraction***
  - N. Mulders, UDelaware
  - Shrinkage <5% (by volume)
  - Mechanically robust

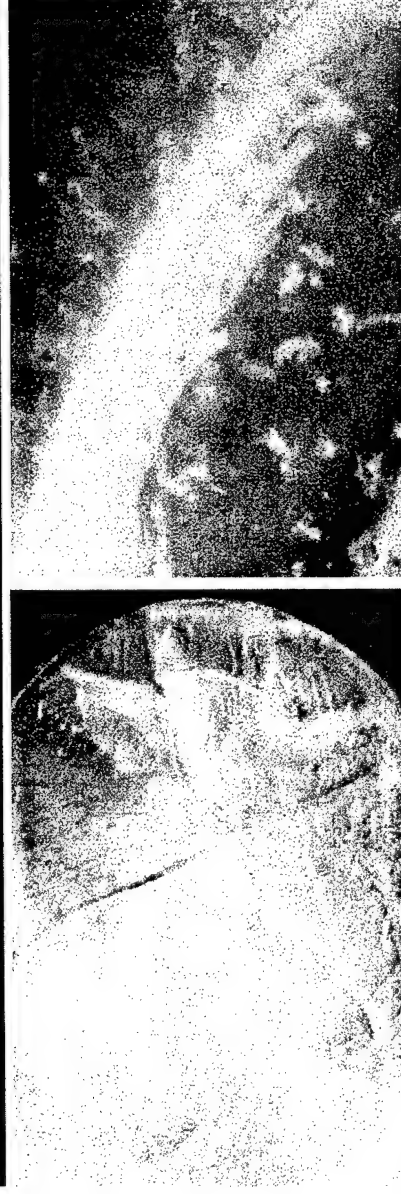
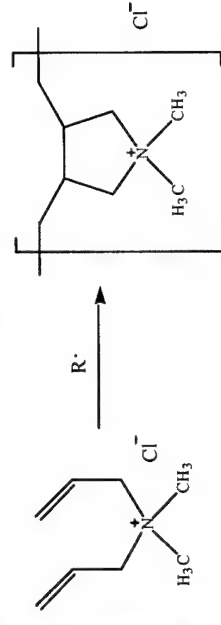


# Permeability of Matrix: A Simple Polymer/Silicate Composite:

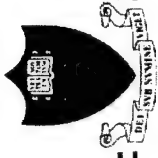
composite      silicate +      composite      composite  
                         monomer



*In situ* polymerization



K. J. Edler, and S. M. Gruner,  
unpublished research (1998)

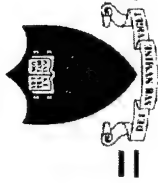


## Holographic Storage Medium

- *Store information 3-dimensionally, throughout the medium, not 2-dimensionally as with other storage technologies*
  - Collaboration with H. Katz, Lucent Technologies\*
- *Uses few or no moving parts, permitting greater data processing speeds*
- *High storage densities*
- *Parallel data read for faster access*
- *Robustness and error insensitive (e.g., redundant)*

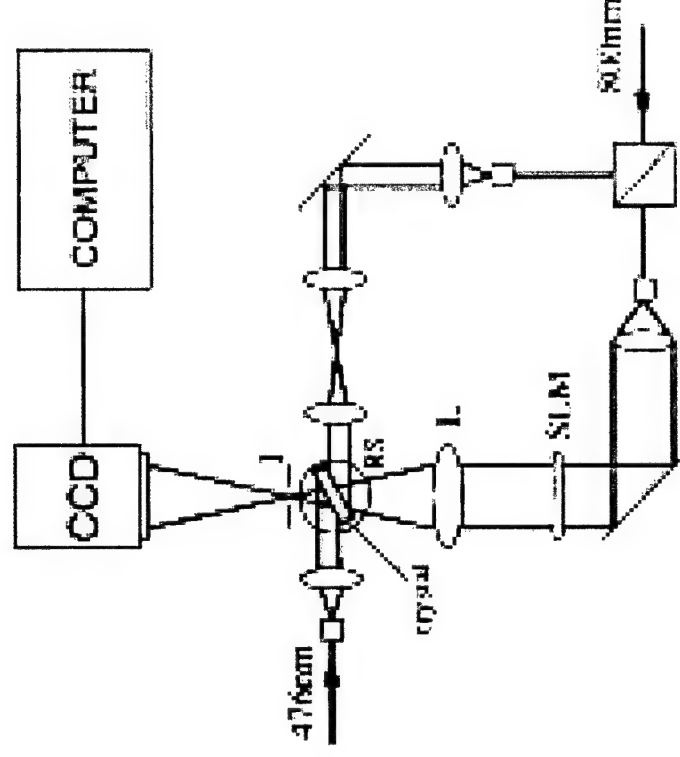
\*Postdoctoral researcher support provided for two years (\$100,000)

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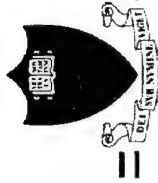


# Nonvolatile Volume Storage

- *Write function superposes two wavelengths*
- *Read function uses one wavelength, preventing data erasure during read*
- *Efficiency of storage medium affected by:*
  - Scattering from matrix
  - Photosensitivity during read/write
  - “Cross-talk” at high information densities

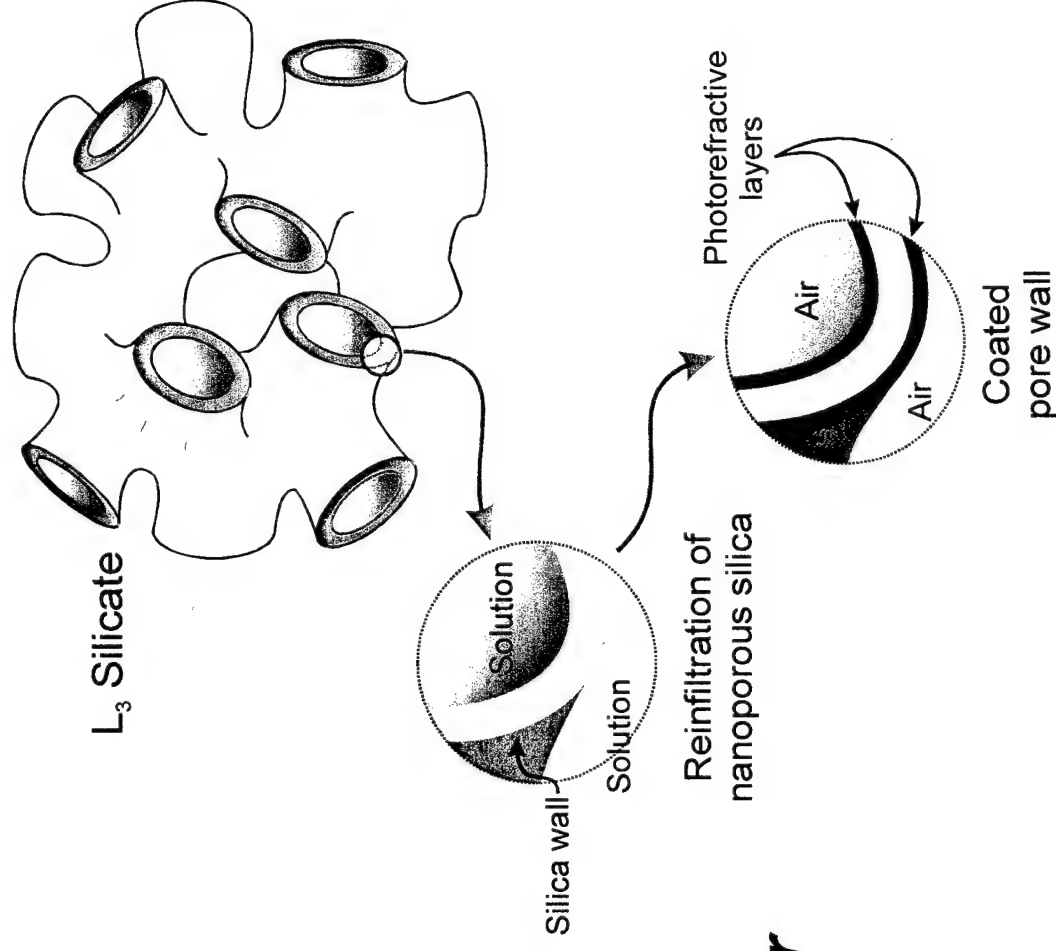


L. Hesselink, S. S. Orlov, A. Liu, A. Akella, D. Lande,  
R. R. Neurgaonkar, *Science* **282** 1089-94 (1998)



## **L<sub>3</sub> Silicate as Support Matrix**

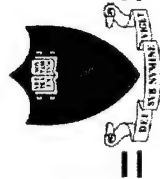
- ***Infiltration of matrix with precursor solutions***
  - Lucent Technologies
- ***In situ reaction to form photorefractive material***
- ***Large pore diameters (>400nm) to maintain transparency***
- ***High density cell walls for improved durability***
- ***Low cost***



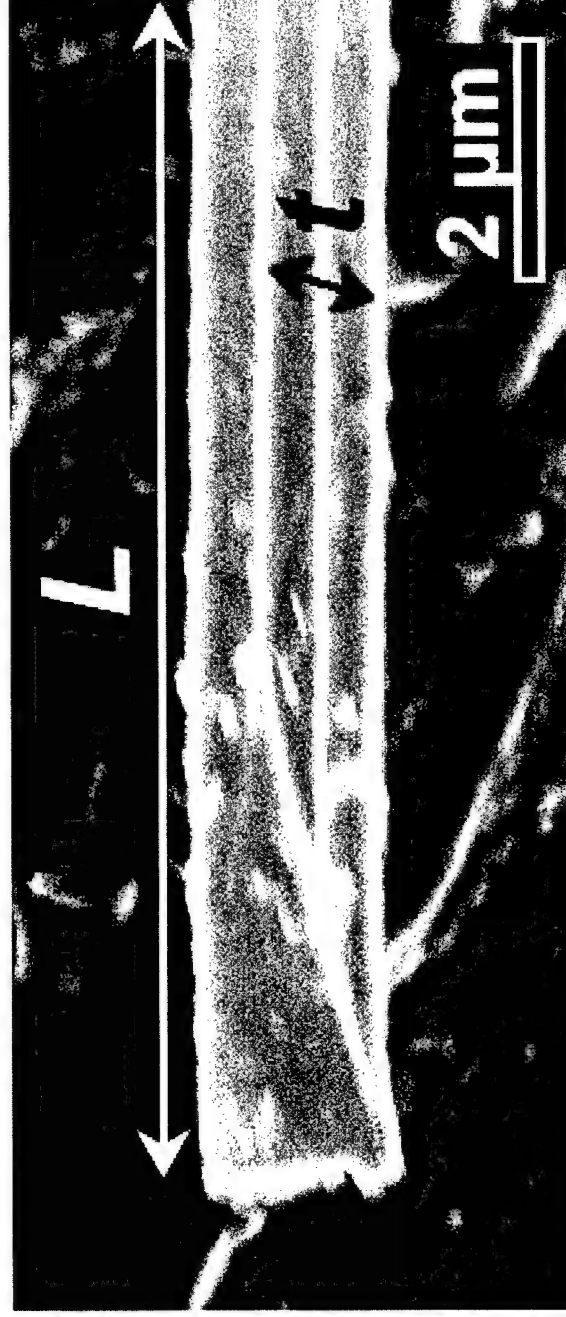
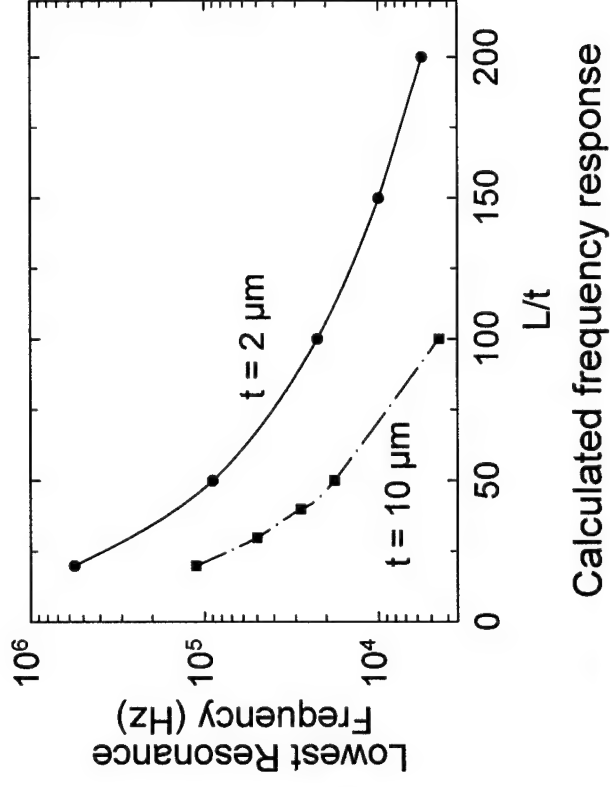
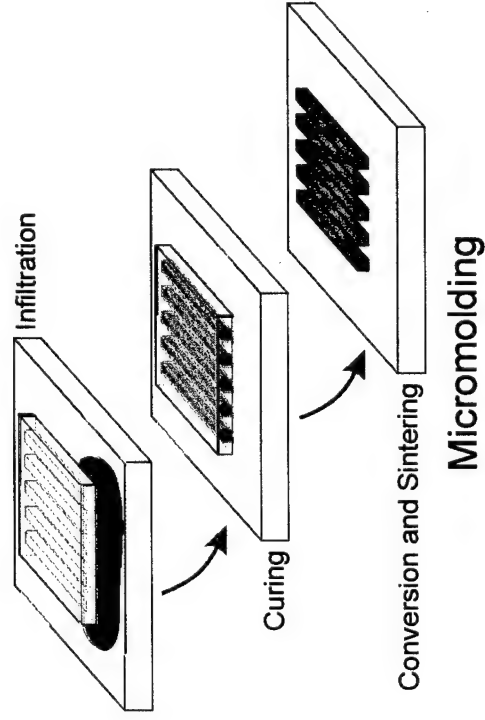


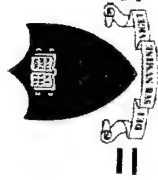
## Thin Films and Coatings

- ***Coatings in micro-electromechanical systems (MEMS)***
    - **Combining MEMS-based sensors with biological receptors**
      - ◆ Collaboration with J. Carbeck, Princeton University
      - ◆ *In vivo* microdevices for biosensing applications
    - **Role of the mesostructured silicate:**
      - ◆ Help to chemically passivate PZT to retard leaching
      - ◆ Protect and isolate metallic electrodes from the environment
      - ◆ Provide a surface for the coupling of receptors and ligands
  - ***Thin films***
    - **Continuous films for low  $k$  dielectric applications**
      - ◆ High uniform porosity with structural coherence
-

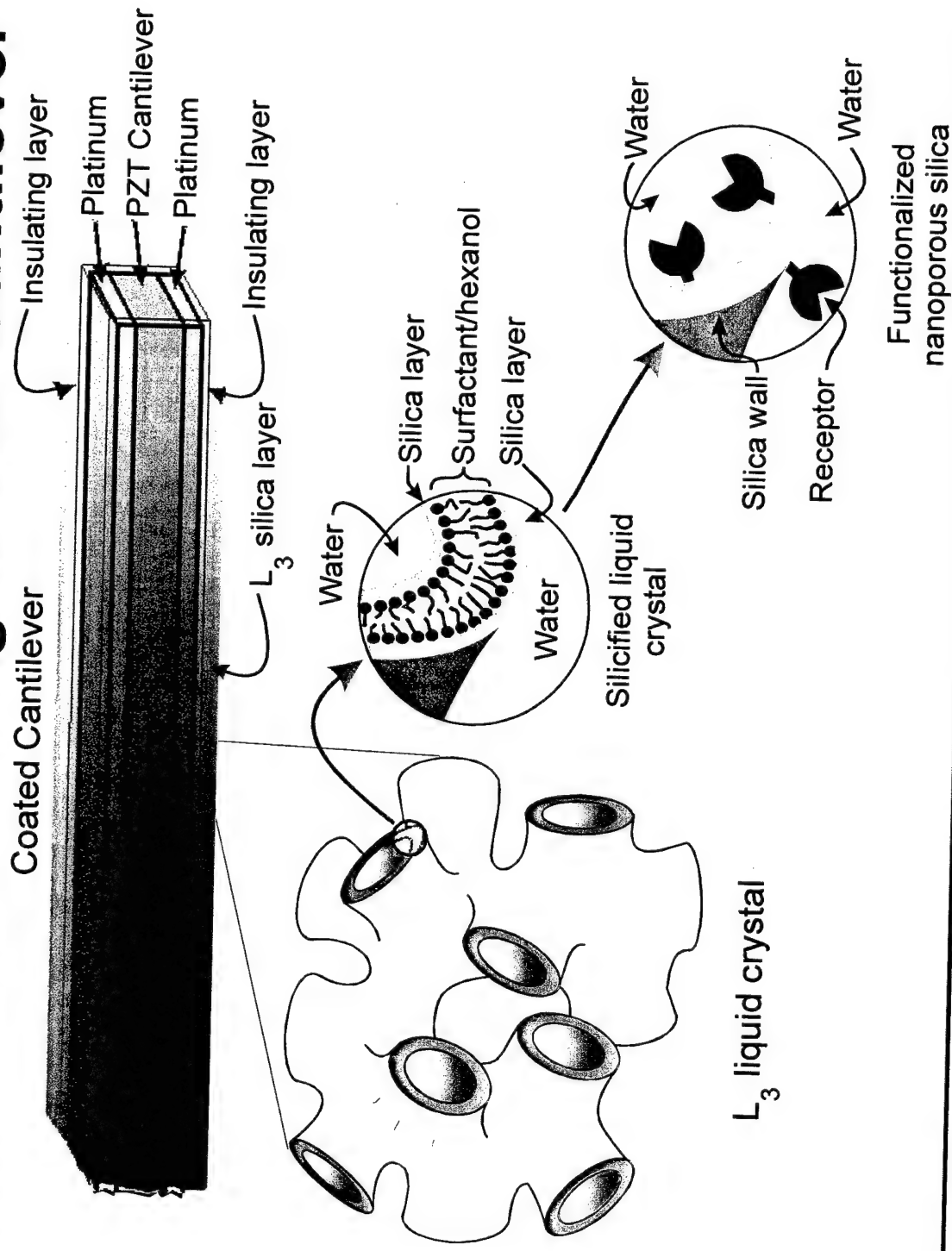


# PZT Microcantilever

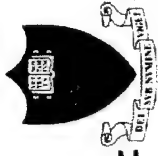




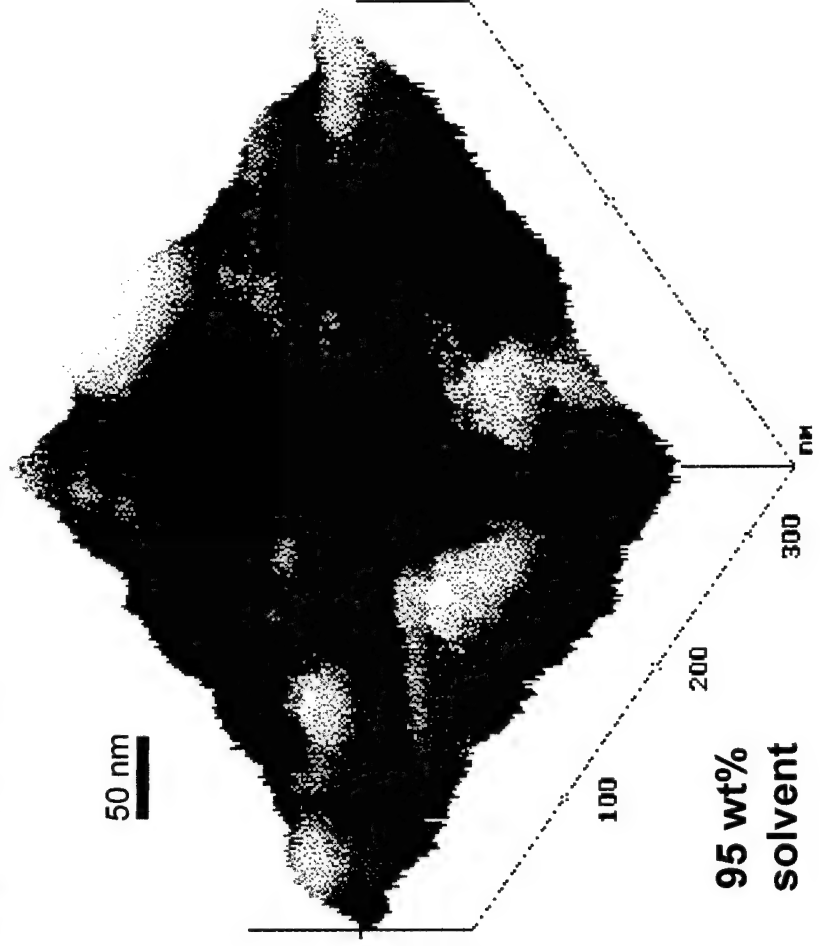
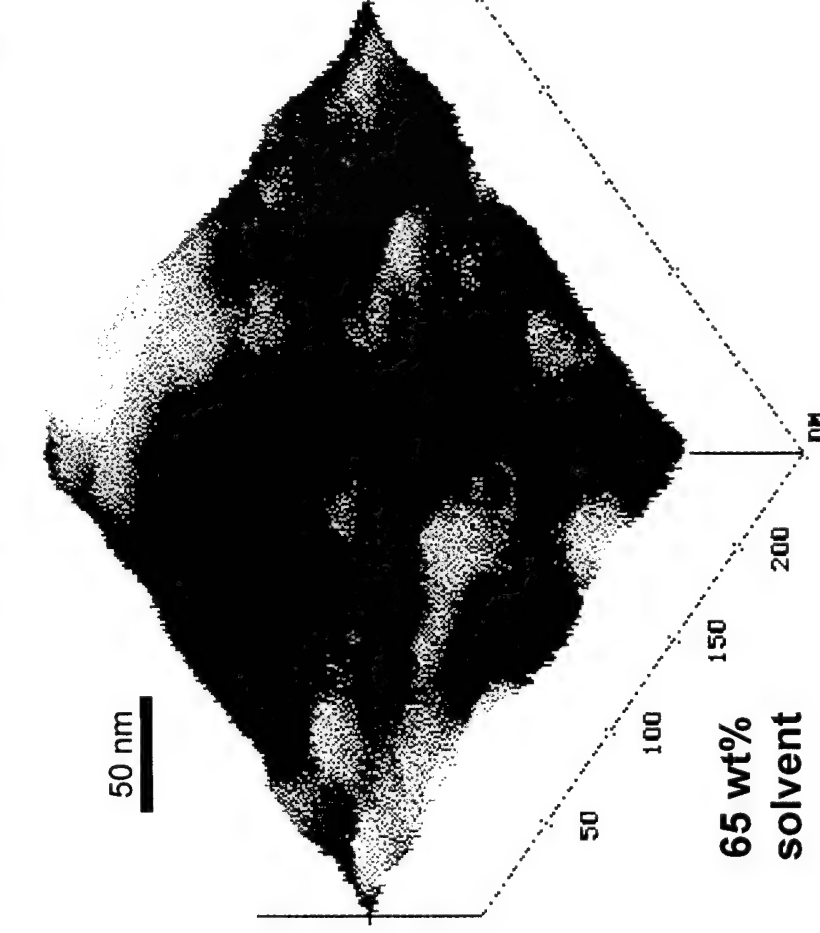
# Mesostuctured Coating on PZT Cantilever



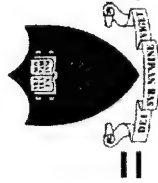




## Thin Films: Tunable Mesopores

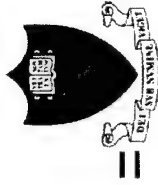


- Spin-coating retains apparent  $L_3$  structure with tunable mesopores



# Ultracapacitors

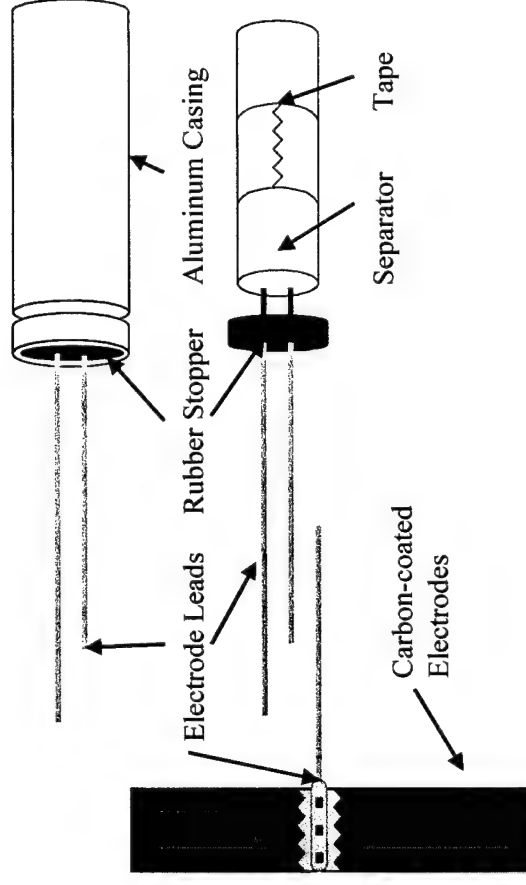
- **Goals**
    - High energy storage densities
    - Mechanically robust
  - ***Perceived advantages of  $L_3$ -structured materials***
    - High surface area
    - Uniform pore diameters
    - Excellent connectivity of surfaces
    - Uniform wall thickness
-



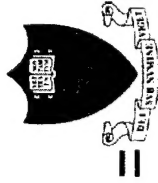
# Commercial Ultracapacitors

## • Approach

- Determine necessary conditions for ultracapacitor through
  - ◆ reverse engineering of commercial ultracapacitor
  - ◆ constructing a comparable ultracapacitor from high surface area materials and appropriate electrolyte
- Utilize L<sub>3</sub>-templated substrates for constructing ultracapacitor



Schematic of a Panasonic Gold series ultracapacitor (EECA0EL334); a high surface area carbon-coated electrode is formed into a spiral wrapping around a central electrode lead; high conductance electrolyte fills the voids



# Cyclic Voltammetry for Measuring Capacitance

$$\text{Capacitance} = \frac{1}{2} \oint I dV \left[ \frac{dV}{dt} V_P \right]^{-1}$$

where:

*closed loop is the “voltage window”*

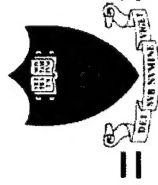
*I is the current in amperes*

*V is the electrode potential in volts*

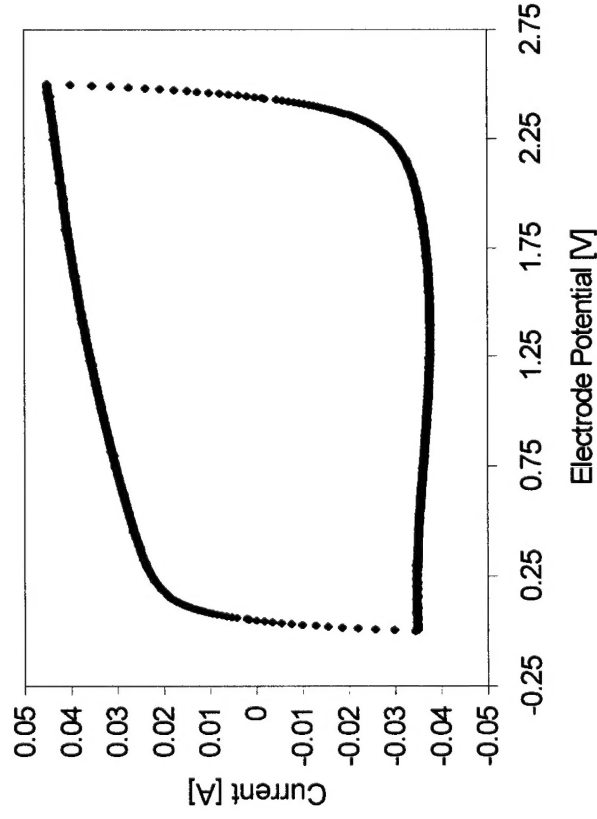
*dV/dt is the voltage sweep rate in  $V s^{-1}$*

*$V_P$  is the peak voltage*

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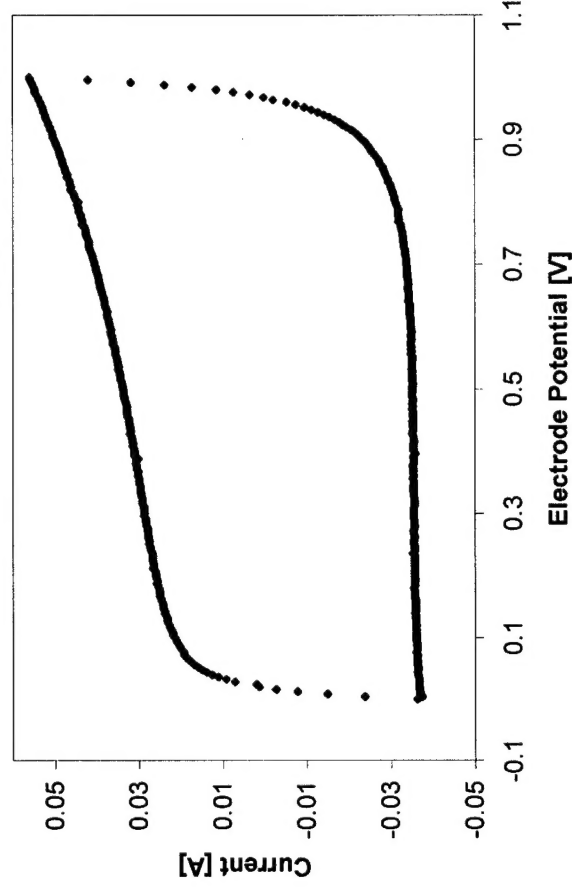


# Comparison of Commercial and Model Ultracapacitors



Panasonic EECA0EL334 ultracapacitor  
Capacitance = 0.33 F

Specific surface area =  $1040 \pm 20 \text{ m}^2\text{g}^{-1}$



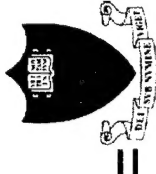
LLNL carbon model ultracapacitor  
Capacitance = 0.33 F

Specific surface area =  $700\text{-}750 \text{ m}^2\text{g}^{-1}$



## Results and Future Work

- *Highly conductive substrate coupled with high surface area are mutual requirements for ultracapacitance, based on enhancing the double-layer*
  - *$L_3$  silica must be activated for use in ultracapacitors*
    - Possible activation of surface by electroless deposition of metal on pore walls
  - *$L_3$  structured, high conductivity substrates through direct templating of liquid crystal*
-



## Continuing Studies

- *Ultracapacitors*

- Direct templation of liquid crystal
- Metallization of pore walls through electroless deposition

- *Holographic Media*

- Casting of suitable monoliths
- Supercritical extraction
- Reinfiltration and *in situ* processing of photorefractive layers on mesostructured silicate substrate

- *Thin Films and Coatings*

- Passivating layers
  - Activated surfaces (biosensors, metallization)
-